

University of Nottingham Faculty of Engineering Department of Mechanical, Materials and Manufacturing Manufacturing Metrology Team

Calibration of focus variation microscopy for surface texture measurement

Ph.D. thesis written by

Anas Ibrahim Alburayt

Supervisors:

Prof. Richard K. Leach Dr Wahyudin P. Syam

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Abstract

Developments in manufacturing technologies have led to the ability of product fabrication with complex deterministic surface topography, designed to have specific functions. The measurement of surface topography has become increasingly important in recent years. In industry and research environments, the most popular methods for surface texture measurements are i) profile measurement (line profiling) and ii) areal measurement with either contact (tactile) or non-contact (optical) instruments.

Profile measurements have been used for many decades, whereas areal measurements are relatively recent technique, compared to profile measurement, that can cover large areas of surface textures to have more comprehensive information about a surface. Areal measurements can be conducted using contact and non-contact surface texture instruments. Measurements using optical instrument are still less understood compared to contact stylus instruments; but optical measuring instruments have significant advantages over contact instruments in terms of relatively short measuring times, accessibility for small delicate surface features and minimal damage to surfaces. Therefore, establishing the traceability of optical measuring instruments is very important to have reliable areal surface topography measurements.

Focus variation microscopy (FVM) instrument is an optical areal surface topography measuring instrument. The measurement traceability of the FVM can be established by determining its metrological characteristics. Measurement traceability is achieved when an unbroken chain of calibration processes to the definition of metre, with stated measurement uncertainties at each step. The Organisation for International Standards (ISO) has proposed metrological characteristics for optical areal surface texture measuring instruments, including for FVM instruments. These metrological characteristics, which directly affect measurement results, should be quantified to calibrate the FVM instrument for surface topography measurement.

FVM is a popular instrument used for various type of surface topography measurements obtained from various manufacturing processes, including both subtractive and additive, and various surface coating processes. However, the establishment of FVM's traceability to get reliable measurement results is still challenging. Because, most of FVM instruments cannot, or at least are very difficult, to measure very smooth surfaces with Ra < 10 nm. Due to this reason, the available calibration infrastructures (including reference artefacts, and calibration procedures and methods) for areal surface topography measuring instruments cannot be applied for FVM because the infrastructures are based on the use of very smooth reference artefacts.

This research project aims to develop novel calibration infrastructures, including novel artefacts, procedures and methods to quantify the metrological characteristics of the FVM. The project provides calibration infrastructures by using novel low-cost material measures and novel practical procedures to determine the metrological characteristic for FMV. The metrological characteristics of focus variation microscopy include: measurement noise, residual flatness, amplification coefficients, linearity deviations and perpendicularity deviations and topographic spatial resolution. The Low-cost material measures were calibrated with more accurate and traceable measuring instruments to create the traceability link to the metre.

Key words: traceability, surface texture, focus variation microscopy, calibration, measurement uncertainty, metrological characteristics.

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Publications

- Alburayt A, Syam W P and Leach R K 2017 Detecting the signature of motion stage non-linearity for focus variation microscopy using measurement noise and surface topography repeatability The 16'th Conference on: Metrology and properties of engineering surfaces in Göteborg Sweden 26-29'th of June 2017
- Alburayt A, Syam W P and Leach R K 2018 Lateral scale calibration for focus variation microscopy Meas. Sci. Technol. 29 065012
- Alburayt A, Syam W P and Leach R K 2019 lateral image sensor calibration for focus variation microscopy in preparation
- Alburayt A, Syam W P and Leach R K 2019 Methodology to determine topographical spatial resolution with a random surface artefact for focus variation microscopy in preparation.

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Chapter one: Introduction

1 Introduction

Measurements have a daily importance in our lives and are carried out across numerous disciplines, from science to engineering, using different methods. The methods range from simple to advanced, based on the work carried out. Measurement has been defined in VIM (JCGM200 2008, JCGM200 2012) as the 'process of experimentally obtained one or more quantity values that can reasonably be attributed to a quantity'. Measurement in the manufacturing field can be used for different purposes, including studying a sample's surface texture and checking the dimensions of the sample to optimise manufacturing quality. Thus, measurement plays a vital role in manufacturing and is carried out from the design stage through to production, to final quality inspection to completed products. Leach RK, Senin N et al. (2017) recently discussed why measurement has become a fundamental aspect of manufacturing. One of its benefits is related to the improvement of the manufacturing process; for example, in the measurement of surface texture. The surfaces being measured can be of different textures due to different process conditions. From the measurement results, one can monitor the process conditions and improve the process. Studying the different types of surface texture is, therefore, important so as to overcome the issues currently preventing measurement.

1.1 Surface texture

The terminology of 'surface' should be clarified in the beginning. ConciseOxfordDictionary (2011) presents several definitions for this word, one of them being 'the outside part or uppermost layer of something'. This definition indicates the surface as a being the highest part of a body that can be touched. The International Standard (ISO14460-1) also defined the surface of samples as 'a set of features which physically exist and separate the entire workpiece from the surrounding medium'. It can, therefore, be understood that the surface connects an existing feature to its surrounding environment. Blunt and Jiang (2003) Identified the surface of an engineering component as a physical boundary between the work piece and the surrounding environment. These definitions allow one to understand the significance of the surface; it is an essential part of an object that can provide information about the object's geometry (Leach, Weckenmann et al. 2014). Surfaces can form different textures, which depends on the surface material type and the process that generate the surface. Therefore, understanding the property of surfaces is important, as most of the engineering component failures are significantly affected by the condition of the component's surface (Blunt and Jiang 2003). The surface texture has been defined by Leach (2010) and (2014) as 'the features that remain once the form has been removed'. Continuing developments in the measurement of surface texture drives continuing research in the topic. Research on the measurement of surface texture has been carried out for over a century (Leach 2010). Improvement of surface texture measuring methods is constantly required to keep up with developments in manufacturing. Nowadays, manufacturing machines use high technologies to build an array of complex parts, such as laser micro milling machine (Pham, Dimov et al. 2002). The advanced manufacturing technology is able to produce a surface that has been deterministically designed to improve the functionality of the part (Evans and Bryan 1999, Alting, Kimura et al. 2003, Bruzzone, Costa et al. 2008, Whitehouse 2010, Jiang and Whitehouse 2012, Godi and Chiffre 2014, Senin, MacAulay et al. 2014). Some products require a specific surface texture to perform their function. For example, the special patterned-surface of an engine cylinder block and the surface texture of bearing part. The engine cylinder block needs to have a deterministic pattern with valleys to preserve the lubricant on the interior surface while the engine is working. Therefore, a dimpled surface texture or stratified surface texture that has a high deep valley can be used to increase the friction resistance of the cylinder block and achieve the required function and performance (Godi, Kühle et al. 2013, Graboń and Pawlus 2016).

Figure 1 shows the surface texture of an engine cylinder block. From Figure 1, the inner surface texture of an engine cylinder block has a patterned valley that can keep the lubricant. Similarly, the inner bearing surface texture can become as oil reservoir to reduce the issues of friction. These designed surface textures can directly affect the part's function, such as wear resistance, reduce the coefficient of friction and operational lifetime (Stout and Blunt 2001, Jiang, Scott et al. 2007, Vorburger, Rhee et al. 2007, Chand, Mehta et al. 2011, Gupta, Kumar et al. 2013). The requirements for this type of surface texture can be fulfilled using various advanced manufacturing techniques, such as laser texturing process (Etsion 2005, Grabon, Pawlus et al. 2011, Yin, Li et al. 2012, Hsu, Jing et al. 2014).

Making a specifically-designed surface texture is one of the advantages of using advanced manufacturing techniques, for example micro-scale injection moulding, laser texturing and diamond turning. The advanced manufacturing techniques manufacture the designed surface texture with high precision. Subsequently, an accurate surface texture measurement is required to be able to measure and verify the tolerance of the surfaces. Measuring the specifically designed surface texture is challenging due to some reasons, for example the measurement depends on the surface materials, features to be measured are smaller than the optical resolution limit and the measurement with already well-understood tactile instrument is not anymore suitable. Some of surface texture measuring instruments cannot measure all surface types. For instance, the reflective, translucence and high rough surfaces can be difficult to measure in optical instruments.

Leach, Bointon et al. (2018) mentioned that all surface measuring instruments are currently limited to measuring only some types of surfaces. Understanding the different surface types can help improving the measurement process.

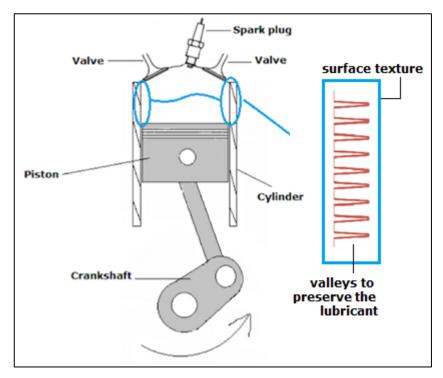


Figure 1: The engine cylinder block and the importance role of its surface

Different methods can be used to measure the surface texture based on the measurement of interest. The types of surface texture methods have been classified into: line profiling, areal topography and areal-integrating (Vorburger, Rhee et al. 2007, ISO25178-6 2010, Leach and Smith 2018). The methods of surface texture using line profiling and areal topography parameters are more popular in the industry and research sectors, as they provide the required data from the measured surface texture using surface topography measuring instruments. The areal-integrating type, on the other hand, relates more to the statistical information of the surface. Figure 2 shows the classification of surface texture measurements. Line profiling as a measurement parameter has been a subject of research focus for over a century (Leach 2013, Leach, Giusca et al. 2014) and has led to numerous publications. Although many measurements have been carried out using line profiling type, these measurement data for surface texture are inadequate. The line profiling type only provides data of a single profile form an entire surface. The areal topography measuring type, on the other hand, can cover a large area of measured surface and provide rich measurement data. For this reason, measurement of surface texture using areal topography has become more popular in research. Moreover, areal topography type can provide comprehensive information on the functional features of the surface (Jiang, Scott et al. 2007, Leach, Flack et al. 2009, Leach, Giusca et al. 2009, Giusca, Leach et al. 2011, Leach, Claverley et al. 2012, Leach and de Groot 2015). This advantage encourages further focus on the areal topography measurement, rather than line profiling. Table 1 compares line profile and areal measurements.

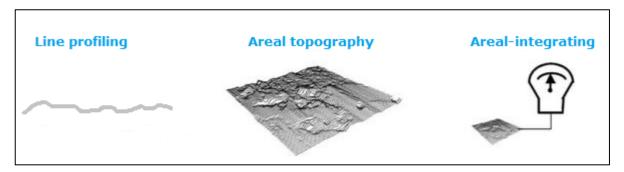


Figure 2: The classification of surface texture measurement

The measurement of surface texture is not a new concept. Areal topography measurements were first made between 1967 and 1970, with the first standard published at the end of 2005 (ISO/IEC17025 2005, Jiang, Scott et al. 2007). The considerable time delay in publishing may indicate slow development of this method. In addition, more focus may have been on line profiling measurements at that time. Jiang, Scott et al. (2007) and Kapłonek, Nadolny et al. (2016) confirmed that areal surface measuring instruments have only become available commercially in the early 1990s. Consequentially, several measurement companies have developed measuring systems that are suitable for areal topography, which have made this type of measurement more popular. The measurement of surface texture using either line profiling or areal topography can provide useful information on the manufactured surface quality; i.e. these instruments can calculate the parameters of Ra and Sa, which are frequently used for assessment of surface quality. Making accurate surface texture measuring instruments is important to obtain a reliable surface data and its surface texture parameters.

Table 1: Comparison of line profiling and areal topography measurements

Line profiling	Areal topography
Line measurement	Area measurement
More efficient data	Adequate data
2D	3D
Traditional measurement	Modern measurement
Only limited region	More real representation

1.2 The measuring instruments

The available surface texture measuring instruments for areal topography measurement operate based on different principles. Some of the instruments require contact with the measured surface, while others do not. The stylus (contact) and optical (non-contact) measuring instruments are the two techniques currently used for areal surface topography (Leach, Giusca et al. 2009, Leach and Smith 2018). The stylus instrument measures the surface texture using a stylus tip. The stylus instrument is commonly used as a reference measuring instrument. The reason is that a mature mathematical model that describes a profile obtained from rolling a ball, that is a stylus tip, across a surface is available. The model allows the prediction of the measuring results with high confident (Leach and Haitjema 2010, Leach and Giusca 2013). However, certain long-standing issues make the stylus instruments undesirable for measurement, in spite of its widespread use in research and industry. For this reason, the advantages of the stylus instrument do not outweigh its limitations. First, the stylus instrument can damage the surface being measured through contact with the stylus tip - this especially concerns measurement of soft surfaces. Moreover, this leads to reading of wrong data. The damage also can be to the stylus itself; for instance, it can break when contacting a surface with high impact. In addition, the stylus instrument proves time-consuming for certain measurements. Leach, Giusca et al. (2014) argued that areal surface texture measurements using a stylus instrument is time-consuming, as it requires multiple setup and calibration steps prior to the measurements. Furthermore, the stylus tip collects the measured data by touching all the determined points on the surface - this not only takes time, but also make the measurement difficult as large areas with complex topography are meant to be covered using areal surface texture measurement. Thus, the stylus instrument is an inappropriate method of areal measurement. Optical instrument, on the other hand, is the preferred alternate method for areal measurement as it overcomes the limitations of the stylus instrument. The optical instruments do not damage the measured surfaces and the short measuring times make this method easier to employ

(Whitehouse 2002, Leach 2004, Hansen, Carneiro et al. 2006, Leach and Haitjema 2010, de Groot 2015, Tosello, Haitjema et al. 2016). Table 2 shows the differences between the stylus and optical instruments. From table 2, optical instruments are more preferable to be used as areal surface texture measuring instrument. For instance, mounting the stylus component onto the system prior to measurement is not a requirement when using the optical instrument. Instead, the surface is measured using the instrument's illumination source through the objective lens or other methods, such as ring light. Although the optical instrument overcomes the stylus instrument in a number of ways, it is currently difficult to interpret the measurement results obtained using the optical instrument. The electromagnetic wave interaction between the light source and measured surface has no analytical solution to estimate the measured surface (Leach and Haitjema 2010, Foreman, Giusca et al. 2013, Leach, Giusca et al. 2014).

Table 2: Differences between stylus and optical instruments

Stylus	Optical
Stylus can be broken	No damage
Geometrical measurement	Optical path measurement
Slow measurement	Fast scan

Optical instruments for surface texture measurement operates using several techniques - similar in their measurement principles, but different in how they operate. optical instruments, available commercially to measure surface topography, comprise coherence scanning interferometry, confocal microscopy, digital holography, light scattering and focus variation (Leach and Giusca 2013, Leach, Giusca et al. 2013). Light scattering, notably, is used to statistically measure the surface parameter (area-integrating measurement) (Leach and Haitjema 2010). These optical instruments have been increasingly used in research and industry. The traceability of optical instrument has become important. To realise measurement traceability, an unbroken chain of calibration to the definition of a metre has to be established. The optical instrument should be calibrated against a more accurate measuring instrument and the measurement uncertainty of the calibration procedure should be stated for traceability. The calibration of areal surface texture instruments has received significant attention in research (Jiang, Scott et al. 2007, Leach and Giusca 2013, Leach, Giusca et al. 2015) and this has led to an international standard used to define specific characteristic for optical instrument calibration. The ISO25178 series is the international standard used for the calibration of areal surface texture instruments. The ISO25178 includes metrological characteristics (MCs) for the calibration process; these comprise measurement noise, flatness deviation, linearity deviation, amplification coefficient, *X-Y* mapping deviations, topographic spatial resolution and topographic fidelity (ISO25178-601 2010, Leach 2011, ISO25178:600 2012, ISO25178-606 2015, Leach, Giusca et al. 2015, ISO25178:600 2017, Haitjema and Leach 2018, ISO25178:600 2018). The details of these characteristics will be discussed in the next chapters. The optical measuring instruments such as for coherence scanning interferometry and confocal microscopy have been calibrated by determining the MCs. However, the calibration of FVM has not previously been completed using the MCs determination. This research will calibrate the FVM by completing the MCs determination.

To have a reliable surface texture measurements, the traceability of the measurement results should be established. To establish the traceability, optical measuring instruments for areal topography measurement should be calibrated by determining their MCs. Specifically for common FVM instruments, common available reference artefacts have very smooth and reflective surfaces so that the common FVM instruments cannot obtained the measurement of the artefact surfaces to calculate the MCs. Hence, new artefacts along with certain practical procedures (easy to carry out in a reasonable period of time) should be proposed to be able to determine MCs for FVM instruments.

1.3 Research aims

The thesis aims to investigate the traceability framework by determining the metrological characteristics (MCs) for a focus variation microscopy (FVM) instrument, as an optical areal surface texture measuring instrument. The investigation will comprise both development and manufacturing processes for a novel suggested reference artefact to determine the MC of the FVM. In addition, development of the calibration procedures will be included in this investigation. The research objective is to estimate the uncertainty of the measurement results. The aims of the thesis will be addressed by the following process. Each MC for FVM will be determined separately by measuring a suitable artefact in a separate experiment. If a suitable artefact for FVM is not available, a new low-cost artefact will be designed and manufactured. The new artefact will be calibrated with a more traceable measuring instrument to achieve traceability. The results for the new artefact with the more traceable instrument will be compared with the FVM and the uncertainty estimated.

1.4 Research questions

The method used to determine the MCs for FVM is important. Most of the available artefacts cannot be measured with FVM because of its measuring limitations with measuring smooth and transparent surfaces. Therefore, measuring a suitable artefact is important in this research project. The artefact used to determine the MCs for FVM will influence the choosing of good practical procedures. This research project focuses on FVM calibration by determining its MCs and has been motivated by the following research questions:

- 1- How can the MC of FVM be determined?
- 2- What are the suitable artefacts to determine the MCs for FVM?
- 3- What are good practical procedures to determine the MC with the suitable reference artefacts?

In this thesis, each MC of FVM can be determined by addressing some experiments. Four experiments will be implemented in the determination of measurement noise and measurement repeatability using the replica of an optical flat surface and flat surface artefacts. The determination of measurement noise will be with different measurement parameters, that are illumination parameters, contrast and brightness parameters. In addition, the determination will be with different scale location of the vertical motion stage and objective lenses. The residual flatness determination will compare ISO filtering rule and the proposed filtering method using two objective lenses of 50x and 100x. The proposed filtering method is applied by multiplying the sample distance of the field of view of each objective by ten. The ISO filtering process is a low pass Gaussian filter as stated in the ISO standard to generate an SFsurface with a cut-off the value that is equal to one-tenth of the field of view. The amplification, linearity and perpendicularity characteristics will be determined in three novel experiments, using novel and low-cost reference artefact. The determination will be performed for the lateral scale with multiple-image field measurements; vertical scale; and measuring the lateral scale with single image field measurement. Three new low-cost artefacts will be proposed to determine characteristics in vertical and lateral scale calibration. The cross-grating artefacts will be for the lateral scale calibration experiment and step height artefact will be for vertical scale calibration. The lateral period limit (LPL) will be determined using a novel method. The novel method will be presented using an artefact with a random surface.

1.5 Thesis structures

The following chapters will discuss the details of this project. Chapter 2 reviews the literature regarding the research project and is divided into two sub-sections: the calibration of areal surface texture measurements and the working principle of the optical instrument technique used here (FVM). The details of proposed artefacts used in the experiments of determining the MCs for FVM are in Chapter 3.Chapters from 4-7 will present the experimental results (proposed artefacts and procedure) to determine the MCs of the FVM. Measurement noise calibration will be reported in Chapter 4. Chapter 5 will report residual flatness calibration and Chapter 6 will report the calibrations of amplification, linearity and perpendicularity. Topographic spatial Resolution calibration will be reported in chapter 7. The final chapter will conclude and summarise the results of this thesis, including suggested future works.

Chapter two: Literature review

2 Literature Review

2.1 Metrological traceability

Traceability is an important terminology used in metrology, and, as being stated by Leach and Giusca (2013), it is as one of the most fundamental concepts. Traceability is indicated as one of the metrological pillars of the field. Leach (2010) and Leach (2014) claimed that any measurement in any manufacturing system must be traceable and documented. Traceability should be available in any measurement processes so that its value should be clearly demonstrated. Traceability assures in obtaining reliable and trustable measurements (Leach and Giusca 2013, Moroni, Syam et al. 2018) – i.e. it ensures measurement accuracy. Therefore, the subject of traceability is a fundamental topic when discussing metrology.

The international vocabulary of metrology (VIM) (JCGM200 2008, JCGM200 2012) has defined metrological traceability as 'property of a measurement result whereby the result can be related to a reference through a documented unbroken chain of calibrations, each contributing to the measurement uncertainty'. This definition highlights that traceability can be achieved using a calibrated reference through an unbroken chain of calibration at all stages. This reference can be a calibrated material measure and/or traceable measuring instrument. Often, the instrument calibration achieves the traceability using a calibrated artefact (Leach 2010, Leach 2014). In addition, the mention of measurement uncertainty in the above definition shows the importance of traceability. Leach and Giusca (2013) and Leach, Giusca et al. (2015) stated that uncertainty is essential to and always an aspect of traceability; traceability cannot be established without stating uncertainty. Morel (2006) mentioned that measurement uncertainty is an essential element in traceability and that measurements cannot be compared if the uncertainty is not stated. Without stating the measurement uncertainty, the traceability chain cannot be constructed and a measurement may not yield a meaningful result. The method used to demonstrate the measurement traceability is a calibration (ISO25178:700 2018). Calibration along with measurement uncertainty are the essential part of metrological traceability.

Traceability can be achieved to different instruments for both profile and areal measurements; this has been discussed for stylus instruments for some years (Leach, Giusca et al. 2015). However, current traceability for areal surface topography instruments is, as yet, unsatisfactory, as the measurement conducting using stylus instrument takes relatively longer time (Leach and Giusca 2013, Leach, Giusca et al. 2015).

The unbroken chain mentioned in the metrological traceability definition is a 'sequence of measurement standards and calibrations that is used to relate a measurement result to a reference' (JCGM200 2008, JCGM200 2012). This definition confirms the importance of the unbroken metrological traceability chain; moreover, Whitehouse (2003) and (2010) demonstrated that traceability is a measurement procedure employed for both national and international measurement standards. Once an instrument is traceable, it can be claimed that the measurement it provides will be accurate and reliable. The traceability chain infrastructure starts from the definition of the metre, which is the highest level in the traceability chain, to measurements conducted in the industry. The definition of metre is 'the length of the path travelled by light in a vacuum in a time interval of 1/c of a second, where c is the speed of light given by 299 792 458 m·s⁻¹' (Petley 1983). Figure 3 shows the unbroken chain of the metrological traceability infrastructure.

The traceability process can be carried out using a primary instrument that has already been traceable – i.e. an instrument that is traceable and more accurate than the calibrated secondary measurement. Any instrument that is being calibrated with a primary instrument can be an example of a secondary instrument. The primary instrument can be used to calibrate a material measure and, then, to estimate the measurement uncertainty of the calibration results. When the calibration of material measure with primary instrument is completed, the secondary instrument can measure the calibrated material measure. The results of material measurements with the secondary instrument can be compared with those of the primary instrument. It should be noted that the definition of a metre has high accuracy and low measurement uncertainty. Thus, when the metrological traceability chain is moving down from the definition of a metre to the instrument that is being calibrated, the measurement accuracy decreases and the measurement uncertainty increases.

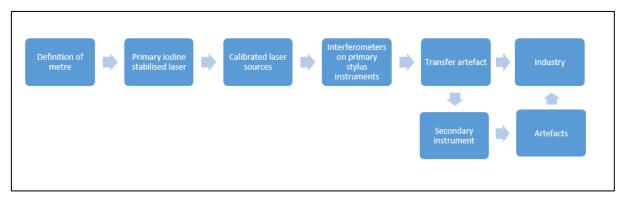


Figure 3: The traceability chain infrastructure

The metrological traceability chain can be applied through a calibration hierarchy 2004, JCGM200 2008, JCGM200 2012, ISO/WD25178-700.2 2014, (ISO/VIM ISO25178:700 2018, Leach and Smith 2018). The calibration process compares two measuring instruments, one of which is more accurate than the other, and the traceability to the metre is established by comparing against the measurement with the higher accurate instrument, that is, commonly the instrument at a national measuring institute (NMI) (Alan 2001, Cox and Harris 2006, Czichos, Saito et al. 2011, Smith 2013, NPL 2018). This calibration process creates the unbroken chain of metrological traceability. Thus, the unbroken chain of metrological traceability confirms that the measurement results obtained are referenced to a high level of traceability metrological chain (definition of metre) (ISO/IEC17025 2005, Hemming 2007, Czichos, Saito et al. 2011, Valery, Anna et al. 2013). When the measurement is linked to the national standard of known accuracy, traceability can be established. Each step in the calibration process should be supported by documented evidence to confirm the linked chain of traceability (Alan 2001, Czichos, Saito et al. 2011, Leach 2011, Estler 2014). Figure 4 depicts the calibration hierarchy according to the national metrology.

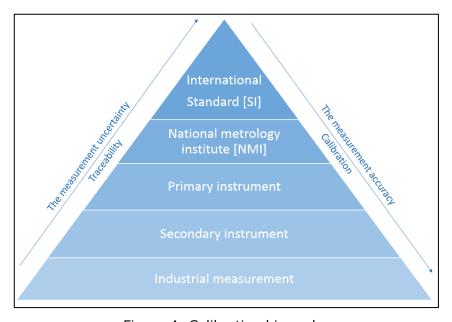


Figure 4: Calibration hierarchy

2.2 Calibration

The term 'calibration' can be used in different disciplines. However, Whitehouse (2003) and (2010) state that 'metrology is only as good as the calibration procedure', demonstrating the importance of calibration in metrology. The calibration of an instrument is one of the fundamental processes in metrology used to maintain measurement traceability (Mathioulakis and Belessiotis 2000, Raghavendra and

Krishnamurthy 2013, Advanced Instruments 2015). VIM (JCGM200 2008, JCGM200 2012) has defined calibration as an 'operation that, under specified conditions, in a first step, establishes a relation between the quantity values with measurement uncertainties provided by measurement standards and corresponding indications with associated measurement uncertainties and, in a second step, uses this information to establish a relation for obtaining a measurement result from an indication'. This definition clarified calibration as a practical procedure that follows required conditions so as to achieve a relationship from the results. Leach and Giusca (2013) and Raghavendra and Krishnamurthy (2013) mentioned that the conditions of an instrument calibration should be the same as those applied on a daily basis. For example, performing the measurement on the same temperature in controlled lab. The definition also emphasised that the measurement uncertainty is of importance in calibration. Smith (2013) and Syam (2018) mentioned that the measurement uncertainty should be stated when performing a calibration process to instruments and its result must be reported and appropriately certified.

The calibration process was explained by Ville (2003) as an operation applied to an element of already known dimensions to assess the measurement of the instrument. Although this explanation is correct, some crucial details relating to the calibration process are missed. Czichos, Saito et al. (2011) and Leach (2011) clarified that the calibration process can be achieved using a direct comparison against a more accurate measuring instrument, or certified material reference. Raghavendra and Krishnamurthy (2013) and Richard et al. (2015) agreed that calibration is a comparison operation between two measurements: one is used as a primary standard of a known value, while the other as the tested value. This method is used to demonstrate measurement traceability (ISO/WD25178-700.2 2014) and to established the traceability chain. Once the traceability with an unbroken chain is achieved, it can be assumed that the calibration process is valid. The results of calibration can then be presented in different ways, such as using a calibration diagram, curve, spreadsheet table or statement (JCGM200 2008, JCGM200 2012, ISO/WD25178-700.2 2014). One or more presentation types for calibration results are acceptable to use, depending on requirement.

The time it takes to perform calibration of a full instrument is the main barrier for industry to apply a calibration process (Leach 2011). The measuring time for the calibration using stylus instrument is time-consuming. Leach (2011) suggests using the optical measuring instrument to reduce the measurement time when measuring areal topography to overcome this issue. ISO25178 provides guide for the calibration process of surface measuring instruments by determining MCs (Giusca, Leach et al. 2011, Leach

2011, ISO25178-606 2015, ISO25178:700 2018). JCGM200 (2012) and ISO25178:700 (2018) state that calibration should not be confused with adjustment, which follows a different process. Giusca and Leach (2013) and Leach, Giusca et al. (2015) mentioned that the aim of the calibration process is commonly misused with adjustment. Instrument adjustment is only performed after the calibration process, typically by the manufacturers of an instrument to correct systematic errors (Raghavendra and Krishnamurthy 2013, ISO25178:700 2018). It is important to consider the differences between the two processes and avoiding misused terminologies.

2.3 Measurement uncertainty

Measurement uncertainty is one of the important terms in metrology that cannot be ignored. The measurement uncertainty can be used in a wide range of measurement results of metrology processes (Bell 2001). Any measurement taken by an instrument carries risks of errors and the true value can be difficult if not impossible to achieve. Measurement uncertainty is instrumental for conducting precise and accurate measurements that allows metrologists to confidently interpret the results and also to established measurement traceability (Bucher 2012, Smith 2013, Chen and Chen 2016, Leach and Smith 2018). Otherwise, the measurement results are ambiguous or not reliable when presented without information about the uncertainty. A level of uncertainty sources accompanies all measurements (Leach 2010, Raghavendra and Krishnamurthy 2013, Leach 2014); and can represent a specific margin with a level of confidence. VIM defined the measurement uncertainty as 'non-negative parameter characterizing the dispersion of the quantity values being attributed to a measurand, based on the information used' (JCGM200 2008, JCGM200 2012). The non-negative parameter mentioned in this definition could be a standard measurement uncertainty. The measurement uncertainty is also defined as the range around the measurement results that contains the true value (Sładek 2015). The measurement results should, therefore, be presented as an interval within which the true value is expected. This degree of deviation in the measurement is described by the statement of uncertainty (Leach 2004, Leach 2014). Therefore, it is important to present the measurement results along with a statement of uncertainty - i.e. a results showing the measurement value, including the uncertainty statement and the confidence level. Leach (2004) and Morel (2006) agreed that a measurement would not be meaningful without stating the uncertainty in the result, but would only be an estimation or approximation of the measured value (Taylor 2009, Grous 2013). Stating the uncertainty shows the reliability of a measurement. In addition, with the stated uncertainty, one can then compare the differences between measurements values of the same surface carried out by different instruments.

Measurement results are deemed to be more reliable or more accurate the lower the uncertainty it has (Rabinovich 2006). The lower uncertainty of measurement results are desirable.

Measurement uncertainty can be estimated using two types of standard uncertainty evaluation, called type A and type B evaluations (Bell 2001, Kacker, Sommer et al. 2007, Czichos, Saito et al. 2011). These two types of standard uncertainty evaluation are different and should be used in any uncertainty evaluation. The guide to the expression of uncertainty in measurement (GUM) clarified the differences between two evaluations; type A is a statistical analysis from repeatability conditions, while type B does not use statistics but instead uses other sources, such as calibration certificates, expert opinions or previous published information (BIPM 2008).

GUM is a reference guide that should be followed when applying measurement uncertainty (Evans 2010, Caja, Gómez et al. 2015, Haitjema 2015, Leach, Giusca et al. 2015, Leach and Smith 2018) as it provides good methodology for estimation. For example, the calculation of uncertainty can be focussed on the parameter. More complex situation in areal surface topography measurements, the influence factor of using filtering and calculating the parameter on the measurement results should be taken into account as the contribution factors of measurement uncertainty (Leach 2011). However, applying the GUM guidelines is not that practical in practice as the procedure involves a mathematical model for surface texture measurement (Harris, Leach et al. 2010, Giusca, Leach et al. 2011, Leach and Giusca 2013) which most of the time the model is unknown or cannot be differentiated. Leach, Giusca et al. (2015) mentioned that the researches on measurement uncertainty from areal instruments is very limited; moreover, while it is available for optical instruments, some further research into this is required.

2.4 Material measure

Material measure in metrology is important to apply the measurement process. Material measures can be standard, where the value is known – such as the gauge block – and this can be used for instrument calibration to achieve measurement traceability. The standard material measure is traceable to the metre through the National Metrology Institute (ISO25178:700 2018). It is clear that when the material measure is traceable, it can be used for instrument calibration. However, different terminologies can be used to describe the material measure. ISO25178-70 (2014) stated that the material measure can also be named as an artefact, calibration sample, calibration specimen, calibration standard, standard artefact, physical measurement standard or physical standard. The

last term is the most recent, one according to Leach, Giusca et al. (2015) and Leach and Giusca (2013). Despite the different terms, all terminologies have the same meaning and principles. Although there is no one rule for which term to use.

There are several definitions for material measure. VIM (2008) and (2012) has been defined the material measure as a 'measuring instrument reproducing or supplying, in a permanent manner during its use, quantities of one or more given kinds, each with an assigned quantity value'. Furthermore, ISO25178-70 (2014) defined the material measure as 'surface texture dedicated manufactured workpiece intended to reproduce or supply, in a permanent manner during its use quantities of one or more given kinds, each with an assigned quantity value'. Both definitions give a general explanation with a similar meaning and are useful to mention so as to cover any differences.

Several material measures are commercially available, as demonstrated by Leach and Giusca (2013) and Leach, Giusca et al. (2015), for profile and areal measurements. For example, the artefacts of NPL bento box. Different companies can provide different material measures and used for specific instrument types. However, there is currently a lack of material measures suitable for FVM. The reason is that common FVM instruments cannot measure very smooth and reflective surfaces (Leach 2011); thus, creating a new traceable artefact to overcome the FVM limitation is required for the calibration of surface texture measurements by FVM. In addition, Danzl, Helmli et al. (2008) claim that a special material measure should be designed for FVM.

2.5 Metrological characteristics

The calibration procedure should be applied following a standard approach. The MCs of areal surface topography instruments for surface texture measurements have been listed in the ISO 25178:600 series as a standard determination for areal surface texture measurement calibration. The concept of MCs is to provide simple and practical routines of calibration for areal surface topography instruments, that can be used by a non-expert user (Leach, Giusca et al. 2015). When the standard calibration is simple, any user in industry can easily perform it. This allows one to confirm that the calibration follows a standard approach and also can be applied by a non-expert user.

The MCs for all areal surface topography instruments comprise a common calibration framework (Leach, Giusca et al. 2015), which can be used to calibrate surface texture measurements. Leach (2011) and Leach and Giusca (2013) demonstrated that instrument calibration must involve MC measurements. Thus, MCs are defined as

'characteristics of measuring equipment, which may influence the results of measurement' (ISO25178:600 2012, ISO25178-606 2015, ISO25178:600 2016). The importance of MCs lies in how they affect the measurement results. As mentioned in the calibration process section of this introduction, measurement uncertainty estimation is an integral part of this process. Leach (2011) and ISO25178:700 (2018) define the calibration process of surface texture measurements as a simple series of tasks that can evaluate the uncertainty of MCs; thus, there is a connection between calibration and MCs and the latter directly contribute to the measurement uncertainty (ISO25178:600 2012, ISO25178-606 2015, ISO25178:600 2016, Leach, de Groot et al. 2018).

The MCs involve measurement noise, flatness deviation, linearity deviation, amplification coefficient, *X-Y* mapping deviations, topographic spatial resolution and topographic fidelity (ISO25178-601 2010, ISO25178-606 2015, Leach, Giusca et al. 2015, Seewig and Eifler 2017, Haitjema and Leach 2018, ISO25178:600 2018, ISO25178:700 2018). Table 3 lists the MCs of areal surface topography instruments.

Table 3: A list of metrological characteristics for surface texture measurements

Metrological Characteristic	Symbols	Axis
Measurement noise	N_{M}	Z
Flatness deviation	Z_{FLT}	Z
Amplification Coefficient	a_x , a_y , a_z	<i>X,Y,Z</i>
Linearity deviation	I_{x} , I_{y} , I_{z}	<i>X,Y,Z</i>
X, Y mapping deviations	Δ_{PERxy}	X,Y
Topographic spatial Resolution	W_{R}	Z
Topographic fidelity	$\mathcal{T}_{ t FI}$	X,Y,Z

The methods of determining the MCs have been developed by NPL, in particular for the stylus instrument, confocal microscopy and coherence scanning interferometry (Leach and Giusca 2013, Leach, Giusca et al. 2015). These methods can be used as a guide for other areal surface topography instruments, although individual instrument specifications should be considered. The current lack of suitable material measures for focus variation microscopy (FVM) can make determining some of the MCs problematic (Giusca, Claverley et al. 2014).

2.5.1 Measurement noise

Measurement noise, as discussed in ISO 25178, is one of the metrological characteristics of an areal surface texture instrument. The measurement noise is an essential metrological characteristic for instrument calibration (Leach, Giusca et al. 2015, de Groot 2017, de Groot and DiSciacca 2018). It has been defined in ISO25178:600 (2012), ISO25178-606 (2013), ISO25178-606 (2015) and ISO25178:600 (2018) as the 'noise added to the output signal occurring during the normal use of the instrument'. This definition means that the noise can affect the measurement analysis from an instrument and can thus affect the instrument's performance in terms of its measuring accuracy. In addition, measurement noise contributes to the measurement uncertainty (Giusca, Leach et al. 2012, ISO25178-606 2015, ISO25178:600 2018). It is clear that identifying the measurement noise inherent in the instruments can assist in estimating measurement uncertainty, since measurement noise will be one of the uncertainty contributors. When the measurement uncertainty is estimated, a measurement is reliable and traceable.

Noise within a measurement can originate from a number of different sources depending on the working area and the type of instrument. Basically, measurement noise is a combination of environmental noises (external noises) and the internal noises of an instrument, such as the noise of Z axis drive unit during scanning and the noise from the electronics (Giusca and Leach 2013, Barker, Syam et al. 2016, ISO25178:600 2018). Sources of noise within the environment in FVM measurements are temperature and vibration, while electronic noise from e.g. amplifiers and optical noise from e.g. stray light are the sources of internal noises. The noise from the drive units arises from the movement in the Z directions due to the imperfections of the geometry of mechanical components of an instrument.

Measuring instruments in an industrial area have different measurement noise compared to controlled laboratory, for example, NMI's laboratory. Measurement noise in an industrial area environment can be higher than that in a controlled laboratory (Barker, Syam et al. 2016). Machining operation and other rotary machineries in an industrial area is likely to be the source of vibrations which can be the main contributor to measurement noise in industrial environment. Lower levels of measurement noise are more likely obtained in a laboratory where environmental conditions are strictly controlled.

The ability of an instrument to take effective measurements performance can be affected by noises. An instrument's measurement performance capability, i.e. accuracy, is decreased when the noise level is increased. Noise, typically high frequency noise, can limit an instrument's ability to detect small-scale spatial wavelengths of a surface texture (ISO25178-606 2015, Barker, Syam et al. 2016). Noise can thus lead to a loss of information for the surface being measured. However, several process can be performed in order to reduce the noise. de Groot and DiSciacca (2018) claim that the noise can be reduced by averaging over time, smoothing filters or field averaging. Spending long measuring time by reducing the measurement speed can assist to decrease the noise. When the measurement data are averaged over time, the noise can be reduced. The long measuring time, a low measurement noise can be obtained. The noise result can be improved by reducing the measurement speed (Fleming 2013, TechNote(LT05-0010) 2014). The averaging process and using filter in the analysis can also be used to reduce the noise.

Material measure

The measurement of noise can be performed using a specifically designed artefact such as a smooth flat artefact (Giusca and Leach 2013, de Groot 2014, ISO25178-606 2015, ISO25178:700.3 2016). An example of smooth flat artefact is an optically flat material measure (Giusca, Leach et al. 2012). The deviation and roughness of optically flat material measure standard is negligible (Sa / Ra < 10 nm) and usually made of polished (ISO25178-70 2012, EdmundOptics 2018). However, some measuring instruments, for example, FVM have limitations to their measuring specifications and an optically flat material measure cannot be used. The FVM instrument needs to measure the surface contrast for each pixel compared to its neighbouring pixels in the image on the CCD sensor (Leach 2011). Therefore, as the optical flat material measure is smooth and transparent surfaces, its contrast cannot be measured by FVM instrument. For the FVM instrument a different process is required. For an FVM instrument, it is important to be aware of the range of roughness on a flat surface which the instrument can measure (ISO25178:700.3 2016). This is important with this type of instrument in order to avoid its limitations. FVM instruments can measure surfaces that have a surface roughness of greater than 10 nm. Leach (2011) has demonstrated that a replica process, that replicates the surface features of measuring artefact, can be used with a very smooth surface such as an optically flat artefact. Although a replica can assist in solving the surface measurement issues of FVM instruments, it is not always an appropriate method in practice because during the replication process, some features of the original surface may be lost. Macdonald (2014) argues that applying the replica method is not always possible. A reason is that replica materials cannot 100 % replicate a surface so that some feature details cannot be captured and transferred to the replica material. Gasparin, Hansen et al. (2011) confirmed that the achievement of replication degree is

different from material to material. The replication degree is around 1 % for soft redreplica and 8-9 % for hard replica of a contoured artefact. Therefore, the replica operation may fail to replicate some of the features on the original surfaces that have nanoscale differences, such as very smooth or highly polished surfaces. Even when the original surfaces are very smooth, understanding the measurement noise from measuring a replica can still cause problems particularly with validity of the data obtained. Furthermore, some experiments of measurement noise have been conducted without using a smooth surface artefact. The material measure, which has been used for the measurement noise, is flat surface. de Groot and DiSciacca (2018) mentioned that the measurement noise is not limited to exceptional artefact of smooth surface. The results can also be obtained with another type of artefact that has flat surface. For example, using a structured silicon carbide reference flat surface and additive manufacturing artefact. The benefit of using flat surfaces that are far from the smooth surfaces can help to obtain low noise results if capturing the data is limited by the signal to noise (de Groot and DiSciacca 2018). The noise signal using flat surfaces can limit the ability of measuring instrument to capture the data. When the measuring instruments are limited, low measurement noise can be obtained.

Analytical background

Measurement noise is characterised by the parameter Sq_{noise} that is an Sq parameter, the root mean square (RMS) of the surface height measurements, can be used to estimate the amount of measurement noise (ISO25178:700.3 2016) and should be used when conducting measurement noise experiments. Measurement noise can be calculated using two techniques: subtraction and averaging (ISO/WD25178-700.2 2014, de Groot and DiSciacca 2018). These techniques can be applied to identical collected data but are different in their calculation methods. Giusca and Leach (2013) state that the results of the subtraction and averaging methods should be similar, therefore the same effect should be achieved by using both methods, and the most efficient method can be chosen by the user. When the results are not similar, the calculation process may not be correct or a non-stationary surface data occur that makes the averaging method fails to work (Baker et al., 2016).

For the subtraction technique, two measurements are taken at the same sample position and one is subtracted from the other (Giusca, Leach et al. 2012, Giusca and Leach 2013, ISO25178:700.3 2016). This operation removes the form and the underlying roughness of the surface. The equation that can be used after subtracting the measurements to estimate the measurement noise Sq_{noise} is:

$$Sq_{noise} = \frac{Sq}{\sqrt{2}}$$
 (1)

Where Sq is the root mean square value of the scale limited surface after subtraction. To reduce the measurement noise variability, repeating the subtraction operation at least three times is advisable (Giusca and Leach 2013).

The averaging technique is another method for calculating measurement noise. According to Hiersemenzel (2013), this method for calculating measurement noise was first introduced by (Haitjema and Morel 2005). This method is based on the assumption that the contribution of instrument noise to multiple surface topography measurements at the same location can be decreased by the square root of the number of measurements (Hiersemenzel, Singh et al. 2012). When the data from several measurements can be averaged automatically by the acquisition instrument software, the average method can be useful. Using this method, the measurement noise is calculated as follows:

$$Sq_{noise} = \sqrt{\frac{Sq^2 - Sq_{mean}^2}{1 - \frac{1}{n}}} \quad (2)$$

where Sq is the root mean square height of the un-averaged surface topography, Sq_{mean} is the root mean square height of the averaged surface topography, and n is the number of measurements (Giusca and Leach 2013). Recommending the most appropriate number of repeated measurements can be difficult (Giusca and Leach 2013). However, when increasing the number of topography measurements does not change the value of the estimated measurement noise appreciably, the number of measurements can be deemed to be sufficient.

Measurement repeatability can be used to estimate measurement noise and is defined in ISO25178:600 (2012), ISO25178-606 (2015), ISO25178:600 (2018), JCGM200 (2008) and JCGM200 (2012). The definition presented in ISO25178-606 (2015) is 'repeatability of topography map in successive measurements of the same surface under the same conditions of measurement'. While ISO25178:600 (2012) and ISO25178:600 (2018) have defined it as 'closeness of agreement between successive measurements of the same surface topography under the same conditions of measurement'. JCGM200 (2008) and JCGM200 (2012) defined the measurement repeatability as 'measurement precision under a set of repeatability conditions of measurement'. Although the definitions in all of these sources have the same meaning and present the same idea, there are slight differences in the explanations. The repeatability of surface topography measurements gives an indication of the likelihood of agreement between repeated measurements

which can be expressed as a standard deviation (SD) (ISO25178-606 2015, ISO25178:600 2018). As this method focuses on the standard deviation between repeated measurements, it is quick to apply. For example, the value of standard deviation for ten measured surfaces can be calculated fairly rapidly. This method can be used as a complementary method for determining measurement noise (ISO25178:700.3 2016) and can thus be applied as part of analytical processes to assist in understanding the obtained values. It can be applied in the last stage of analytical processes after completing the subtraction or averaging calculations.

Previous works

Measurement noise has been studied in the past with different measuring instruments in both laboratory and industrial environments. Giusca, Leach et al. (2012) investigated measurement noise in laboratory conditions for three measuring instruments: a contact stylus, a coherence scanning interferometer (CSI) and an imaging confocal microscope (ICM). The study estimated measurement uncertainty and using the subtraction and averaging methods for measurement noise. Another work of the measurement noise is performed on point autofocus instrument (Maculotti, Feng et al. 2018, Maculotti, Feng et al. 2018). Barker, Syam et al. (2016) have conducted experiments with a coherence scanning interferometer (CSI) in an industrial environment. Measurement noise experiments using the focus variation technique has been conducted by Giusca, Claverley et al. (2014) and Hiersemenzel (2013). Previous experiments of measurement noise using FVM instruments have been carried out with the Alicona G4. Measurement noise experiments will be carried out in this research using an FVM Alicona G5 and the subtraction, averaging methods and measurement repeatability will be applied for calculations.

2.5.2 Residual flatness

Residual flatness for areal topography measuring method has been defined as 'flatness of the areal reference' (ISO25178:600, 2012; ISO25178-606,2015; ISO25178:600, 2018). It has been defined as 'deviation of the measured topography of an ideally flat object from a plane' (ISO25178:600 2016, ISO25178:600 2018, ISO25178:600 2019). These definitions demonstrate that residual flatness is related to the artefact surface and the error within the Z scale measurement rather than the measurement noise from the sensor and optical system. Therefore, the quality of the areal flat is important for this type of metrological characteristic. The flatness deviation can come from a number of sources, such as imperfections in the areal reference, residual flatness or the optical setup of the instrument (ISO25178:600 2016, ISO25178:600 2018). The residual

flatness was measured using a standard Halle flat surface artefact (the details of the Halle flat surface artefact are presented in section (3.1) of chapter 3). Ninety-six sets of data of repeated measurements were collected from different locations. The measured surfaces of areal topography of different measuring locations using FVM were averaged prior to applying the measuring analysis to reduce random noises. Prior to applying the Gaussian filter to generate an *SF*-surface, form removal in term of levelling and thresholding of the averaged surfaces were applied to approximately flatten the surface so that the filtration process could be performed to obtain the result. The details of this process are described in section (5.1) of chapter 5. The parameter that is used to characterise residual flatness is *Sz*. This parameter is related to the highest and lowest points with respect to the reference plane obtained from a flat surface (Leach 2011, Leach and Giusca 2012, Giusca and Leach 2013, Leach 2013, Giusca, Claverley et al. 2014, Blateyron 2015, MichiganMetrology 2016) i.e. the highest peak and the lowest valley. Figure 5 shows the Sz value.

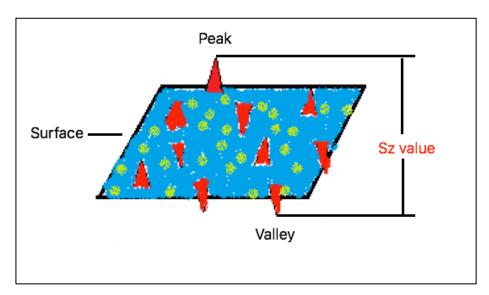


Figure 5: Sz value

Scratches and dirt are examples of local height variations on the measured surface that can affect the value of Sz (Leach 2011, Leach and Giusca 2012, Giusca and Leach 2013, Giusca, Claverley et al. 2014). It is obvious that when scratches or dirt are found on a flat topography, the measurement results could be affected significantly. However, measuring the surface of the artefact at a number of locations in the X and/or Y directions with the same instrument settings can assist in overcoming this problem (vdi/vde2617 2004, Leach 2011, Leach and Giusca 2012, Giusca and Leach 2013, Giusca, Claverley et al. 2014, ISO25178:700.3 2016, ISO25178:700.3 2018). As the condition of the surface at different locations will not be similar, measuring at different

locations leads to a collection of different results from the surface and overcomes the problem. ISO25178:700.3 (2016) and (2018) confirm that using a number of measurement locations can decrease the effects of small deviations on the standard flat artefact. The results of this process therefore tend to be valid and more reliable than those from other processes. The point highlighted here is that it is important to maintain the perfection of the areal reference to reduce the amount of false data. ISO25178:700.3 (2016) and (2018) recommend that at least three different surface locations should be measured.

Material measure

The measurement of residual flatness concentrates on the Z scale errors of the vertical linear stage of an instrument. The residual flatness can be measured using a standard flat surface artefact (Leach 2011, Hiersemenzel, Singh et al. 2012, Leach and Giusca 2012, Giusca and Leach 2013, Giusca and Leach 2013, Giusca, Claverley et al. 2014, ISO25178:700.3 2016, ISO25178:700.3 2018). However, It is important to understand that the standard flat surface required for measuring residual flatness is not a perfect smooth surface (ISO25178:700.3 2016, ISO25178:700.3 2018). Therefore, the roughness of the standard flat surface used should be taken into consideration. When using optical measuring instruments, the limitations of the instrument, particularly for instruments using FVM method must be avoided. In a FVM, a certain degree of surface roughness needs to be present so that contrast values can be calculated for the FVM method to work (Leach 2011).

In practice, the ideal number of measurement repetitions cannot be recommended (Leach 2011, Giusca and Leach 2013). The number of repetitions required depends directly on the stabilisation of the Sz value, so recommending an exact number can be difficult. Every residual flatness experiment has different repeated measurements. The correct value of Sz can only be determined once the value stabilises. Therefore, it is best to simply repeat the measurements until the Sz value remains unchanged.

Filtering and threshold processes

The threshold and filter processes are applied during the analysis of the measured data. These processes can help to avoid spurious data and achieve effective *Sz* measurement (Ismail, Yanagi et al. 2010, Zeng, Jiang et al. 2010, Leach 2011, Giusca, Leach et al. 2012, Hiersemenzel, Singh et al. 2012, Giusca and Leach 2013, Giusca, Claverley et al. 2014). The threshold operation is used to remove irrelevant spike noises in the data. Therefore, the levelling process is carried out prior to the threshold operation. The

levelling procedure can be applied as part of determining the residual flatness (ISO25178:700.3 2016, ISO25178:700.3 2018). From a practical point of view, removing the surface spikes on the levelled surface is an efficient methodology. Using a filtering process, long scale components of a surface can be separated from short scale components of a surface (Seewig 2005, Leach 2010, Whitehouse 2010, ISO25178-2 2011, Seewig 2013, Leach 2014, Blateyron 2015, ISO16610-60 2015, ISO16610-61 2015) so that different aspects such as roughness and waviness can be obtained. In addition, a filter can be used to remove the effects of high spatial frequency noise (Guan, Hirsch et al. 2016). For example, measurement noise calculations. A combination of filtering and threshold analysis can be an effective method for obtaining reliable *Sz* measurements. The filter recommended for the calibration of residual flatness is the *S*-filter (ISO25178-3 2012, ISO25178:700.3 2016, ISO25178:700.3 2018). This filter is a low-pass Gaussian filter with 1/10 cut-off on the field of view (Giusca, Claverley et al. 2014). It is important to apply a standardised procedure for calibration to ensure the correct process is followed consistently and any problems that may occur are avoided.

Previous works

Residual flatness experiments have been carried out previously with a variety of areal surface topography measuring instruments and have included estimates of measurement uncertainty. Giusca, Leach et al. (2012) Performed residual flatness experiments with a coherence scanning interferometer (CSI) and an imaging confocal microscope (ICM). Another work for residual flatness using ICM has been carried out by (Bermudez, Felgner et al. 2018). With FVM instrument, two different methods of carrying out the experiment have been implemented. In one case, the residual flatness data was compared for different averaged surfaces using a filter (Hiersemenzel, Singh et al. 2012). In the second case, a filtering procedure was applied and the results compared with the unfiltered results (Giusca, Claverley et al. 2014). All of these experiments were carried out on a FVM Alicona G4. The experiments in this research will be carried out using a FVM Alicona G5.

2.5.3 The amplification, linearity and perpendicularity

The three metrological characteristics of surface texture measurements are for scales calibration. Both the amplification coefficient and linearity deviation characteristics are focusing on the measurements of the X, Y and Z axes (ISO25178-601 2010, Leach 2011, ISO25178-606 2015, Haitjema and Leach 2018, ISO25178:600 2018, ISO25178:700.3 2018). Therefore, these two characteristics may have the same process in applying the measurement. Due to these characteristics have the same interest in calibrating the

axes, the characteristics can use the same measurement data. For example, when the measurement data of used artefact are collected, both the amplification coefficient and linearity deviation characteristics can use them. ISO25178:700.3 (2018) states that the amplification coefficient and linearity deviation characteristics can use same measurement data in the determination. In addition, Leach (2011) and Giusca and Leach (2013) demonstrate that the relationship of an ideal and instrument response curve on each of the three axes can be established by the amplification coefficient and linearity deviation characteristics. This means that two metrological characteristics can be implemented together with the same experiment. While the perpendicularity characteristic is only focused on X and Y axes. In spite of the perpendicularity characteristic has different interest of axis measurements, it does not mean that the characteristic cannot use the same data of amplification coefficient and linearity deviation characteristics. As the measurement data of the amplification coefficient and linearity deviation for X and Y axes are not containing the measurements data of Z axis, the perpendicularity characteristic can use the same measured data of the amplification coefficient and linearity deviation characteristics in X and Y axes. ISO25178:700.3 (2018) mentioned that the perpendicularity characteristic does not need to be calibrated separately and determined directly. It can be demonstrated that the amplification coefficient, linearity deviation and perpendicularity characteristics can be applied together using the same experiment data.

The definitions can provide more understanding on these characteristics. The amplification coefficient characteristic has been defined as 'slope of the linear regression curve obtained from the response curve' (ISO25178-601 2010, ISO25178:605 2011, Giusca, Leach et al. 2012, de Groot and Beverage 2015, ISO25178-606 2015, Leach, Giusca et al. 2015, ISO25178:600 2018). The response curve here means the instruments' results that are obtained from the measurements. In order to clarify the amplification coefficient definition, an example of linear response curve can be shown in Figure 6. From Figure 6, an ideal curve, response curve and Linear curve which slope is an amplification coefficient are indicated by number (1), (2) and (3), respectively. When the collected values are equal to the input quantity values, it can be assumed as an ideal response (ISO25178-601 2010, ISO25178-606 2015, ISO25178:600 2018). This means that a slope of straight line can be equal to 1. While the linearity deviation has been defined as 'the maximum local difference between the line, from which the amplification coefficient is derived, and the response curve or function' (Giusca, Leach et al. 2012, ISO25178-606 2015, Leach, Giusca et al. 2015, ISO25178:600 2018). Both the definitions of the amplification coefficient and linearity deviation confirm the relationship between these two characteristics. Leach (2011) explained that the relationship of amplification coefficient and linearity deviation can be established by the ideal response curve and the instrument response curve on the scales of X, Y and Z. Therefore, when the amplification coefficient characteristic is determined, the linearity deviation characteristic should be mentioned.

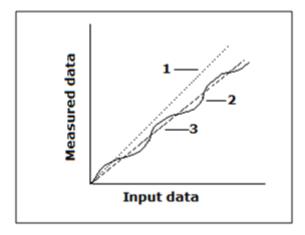


Figure 6: linear response curve

The Perpendicularity characteristic can be related to the amplification coefficient and linearity deviation characteristics. This characteristic can be applied using the same measuring data of amplification coefficient and linearity deviation that focuses on the X and Y axis. The perpendicularity characteristic that is related to X and Y axis is interested on their nonlinearity and can be performed after the amplification coefficient and linearity characteristics. These information were confirmed by the perpendicularity definition. ISO25178-601 (2010), Giusca, Leach et al. (2012) and ISO25178:700.3 (2018) defined the perpendicularity characteristic as 'the perpendicularity deviation between any two of the X, Y and Z axes'. It can be applied by determining the angle deviations between X and Y axis. These deviations occur by different reasons that depend on the measuring instrument type. In the imaging optical instruments, the deviations of the linearity and perpendicularity indicate to the optical distortions (ISO25178:700.3 2018). The optical distortions mean lens error which is very rare appearing perfectly (Mansurov 2015). Figure 7 shows the linearity and perpendicularity deviations.

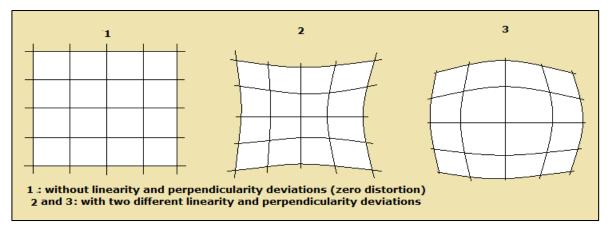


Figure 7: example of linearity and perpendicularity deviations

Material measure

The determination of the amplification coefficient, linearity deviation and perpendicularity characteristics uses a calibrated material measure to perform the experiment. ISO25178:600 (2018) and ISO25178:700.3 (2018) demonstrate that a standard material measure with calibrated depth can be used in the amplification coefficient, linearity deviation and perpendicularity characteristics. The standard material measure means that the material measure is calibrated and traceable with most accurate measuring instrument. Therefore, it is important to notes that the artefact areas should be calibrated prior to performing the measurements (Leach 2011, ISO25178:700.3 2018).

A cross grating artefact can be used for the amplification coefficient, linearity deviation and perpendicularity characteristics. Giusca, Leach et al. (2012) and Giusca and Leach (2013) and Leach, Giusca et al. (2015) state that a calibrated cross grating artefact that has different pitch values is measured to determine the amplification coefficient, linearity deviation and perpendicularity of local characteristic of the lateral scales. The measurement of centre position of gravity is required when measuring the X and Y axes. Therefore, the distances of X and Y plane and the grid positions should be calibrated (ISO25178:700.3 2018). With this type of the artefact, the measurements should cover most of the areas within X and Y axis. ISO25178:700.3 (2018) recommend that 95% is the minimum measurement area of the X and Y lengths. When the measurements are applied on the most of the artefact area, it can give reliable results.

A calibrated step height artefact is another artefact type that can be used in the measurements of Z axis. It is important that using an artefact should be appropriate for the characteristic. Leach (2011) provides that the calibration of Z-axis is often performed

by using a single-step artefact, but it cannot afford a sufficient information. Therefore, using different step height artefacts with different height can be appropriate for the amplification coefficient and linearity deviation in case of measuring the *Z*-axis. The different step height artefact can provide enough information comparing with a single step height. Giusca, Leach et al. (2012) and Leach (2015) argue that the relationship between the ideal response curve and instrument response curve can be established by different step height with various heights. However, it should be noted that the current available artefacts to determine the amplification coefficient, linearity deviation and perpendicularity characteristics are not suitable for FVM instruments due to its limitation of measuring smooth surfaces. Low image contrast of smooth surfaces prevents the CCD sensor of FVM from differentiating one pixel with respect to its neighbouring pixels (Leach, 2011) (please see section 2.6.4 in chapter 2 for more details). Therefore, the FVM cannot capture appropriate measured data of smooth surfaces. To solve this issue, a new artefact must be manufactured when determining these metrological characteristics for FVM.

Previous works

The amplification coefficient, linearity deviation and perpendicularity characteristics have been done with some of areal surface texture measuring. Giusca, Leach et al. (2012) carried out the amplification coefficient, linearity deviation and perpendicularity characteristics with using three measuring instruments such as contact stylus instrument (CS), coherence scanning interferometer (CSI) and imaging confocal microscope (ICM). The calibration was applied on measuring cross grating artefact for X and Y scales and step height artefact for Z axis. Furthermore, these characteristics have been applied using coherence scanning interferometer (CSI) and phase shifting interferometers (PSI) by Giusca and Leach (2013). In addition, de Groot and Beverage (2015) performed the amplification coefficient using interference microscopy. The step height standard artefact and the wavelength scanning standard method have been used in the study. However, the amplification coefficient, linearity deviation and perpendicularity characteristics have not yet been investigated in FVM G5.

2.5.4 Topographic spatial resolution

According to Leach, Giusca et al. (2015), resolution is difficult to define for the areal surface topography instrument, due to problems with determination. Resolution determination uses different procedures for lateral and vertical axes, therefore, defining resolution is not straightforward. However, the latest version of ISO25178:600 (2018) includes the term 'topographic spatial resolution' as a metrological characteristic for the

lateral resolution determination of surface topography instruments. The term topographic spatial resolution provides a definition for different measurement methods. Topographic spatial resolution is defined in ((ISO25178:600) as a 'metrological characteristic describing the ability of a surface topography measuring instrument to distinguish closely spaced surface features'. Although topographic spatial resolution is an umbrella term for different measurement methods, it can be quantified using several parameters and functions.

Resolution can be determined depending on the type of axis; vertical scale (Z-axis) resolution is influenced mostly by measurement noise and residual flatness (Leach and Giusca 2013, Giusca, Claverley et al. 2014, de Groot 2017), therefore, measurement noise can be used to determine Z-axis resolution. However, Z-axis resolution, in this case, is contributed without the lateral component. In their work, Leach, Giusca et al. (2015) agreed that measurement noise can be enough to quantify resolution of the Zaxis, from the measurement uncertainty point of view. Noise measurement is estimated by Sq, which is measured from a flat surface. To contribute to lateral resolution, the lateral period limit (LPL) or 'structural resolution' can be used to determine X- and Y-axis resolution, i.e. the lateral resolution (Giusca and Leach 2013). The LPL closely measures the minimum space between two features, where the depth of the two features can be resolved to at least 50 % of its original depth (ISO25178:600, 2018) (ISO25178:600 2018) (ISO25178:600 2018) (ISO25178:600 2018). In their work, Xie, Lehmann et al. (2012) stated that the role of lateral resolution is becoming more important as well as the axial resolution of measuring instruments. The lateral resolution provides information on the measuring instrument, in detecting the smallest sized features in a surface. The lateral resolution in a 2D measuring instrument can distinguish between the lateral distances between two points, regardless of the depth of the two points. However, 3D measurement of areal surface texture instruments considers the height of features as an essential attribute of that feature. It should be noted that 'lateral period limit' is used instead of 'lateral resolution'. The lateral period limit is used for 3D resolution, or the ability to distinguish two objects on one surface, including correct height measurement (Leach 2011). Therefore, LPL determination can be used in quantifying the topographic spatial resolution for areal surface topography measuring instruments.

LPL has been defined from different sources, such as ISO25178-606 (2015) and ISO25178:600 (2018). The LPL is defined as 'the spatial period of a sinusoidal profile at which the height response of an instrument transfer function falls to 50%' (ISO25178:600 2018). 'Sinusoidal' indicates the type of artefact that can be used for resolution. Additionally, 'instrument' refers to optical and stylus instruments. The

definition states that the height response of an instrument should also be considered. A useful parameter that can be used for instrument response characterisation, is the optical resolution limit which is based on the Rayleigh criterion (ISO25178:600 2018). This criterion is related to the LPL value for the theoretical quantification of the optical lateral resolution.

The LPL is useful in determining the smallest lateral feature that can be meaningfully measured. The LPL is the width limit of a feature, where its depth can still be resolved at least 50% of from its real depth (ISO25178:600 2019). An example is presented in Figure 8, where (A) illustrates LPL and its relationship with the depth of a measured feature. The depth can be reconstructed when the feature width is larger than the lateral resolution (B): the measured depth is equal to the feature depth, and the width is larger than the lateral resolution. However, when the feature width is less than the lateral resolution, the depth cannot be completely reconstructed (C): the width is less than the lateral resolution and the depth is less than the feature depth. It is important to know that the minimum lateral resolution can reconstruct the depth of groove, for example, the measured data can be obtained once the depth limit of the width of groove is constructed.

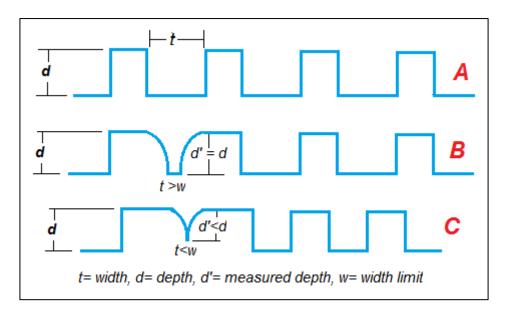


Figure 8: The lateral period limit (LPL).

Material measure

LPL may be determined using different types of artefacts; in their work, Giusca and Leach (2013) stated that a Siemens star artefact could be used to determine LPL. For example, NPL standard artefact of Siemens star. This type of artefact provides

continuous spatial wavelengths to measure resolution in different lateral directions, therefore using this type of artefact is useful in determining resolution, if suitable for the measuring instrument. However, the FVM cannot measure this type of artefact, because it has a very smooth surface (Ra < 10 nm). Therefore, a suitable resolution artefact for FVM is required. Leach (2011) demonstrated that the design of resolution artefact is important in generating high quality resolution measurements. Because the artefact design of resolution measurements can affect resolution values, the resolution of other areal surface topography measuring instruments can be determined using a type ASP material measure, following ISO definitions of lateral period limits (Giusca and Leach 2013). The ASP material measure is a 3D version of Siemens star artefact can provide a continuous variation in spatial frequency (Xu, Fang et al. 2012, Giusca and Leach 2013, Leach, Giusca et al. 2015). Giusca and Leach (2013) used star-shaped artefacts of ASP material to determine the lateral resolution of areal surface topography measuring instruments. Different methods can be used to determine the LPL. ISO25178:600 (2012) states that a vertical edge, sphere or a number of gratings, can determine the LPL, e.g. a rectangular grooved surface artefact can be used when combining limits for full height transmission function.

Previous work

Resolution experiments, using optical measuring instruments, were carried out for several optical instruments. The LPL resolution phase shifting interferometry has been reported by Giusca and Leach (2013). In their work, a star pattern comprising ASP material was measured using a 50x objective lens, along with the analysis method used to calculate the LPL. Results from (Giusca and Leach 2013) were confirmed by measuring step height artefacts, however, FVM resolution has not yet been determined. As mentioned previously, the Siemens artefact, used for resolution determination is not suitable for FVM. Measurement of the Siemens star artefact using FVM is shown (Figure 9). Here, the Siemens star artefact is measured on FVM using 20x and 50x objective lenses. The surface features of the artefact failed to be reconstructed by FVM, therefore, LPL quantification cannot be calculated from this artefact.

In addition, profile measurements of both objectives lens do not provide reliable artefact results. When the surface cannot be reconstructed, resolution determination cannot be performed. Figure 10 shows FVM profile measurements of 20x and 50x objective lenses, therefore, FVM requires a suitable artefact with a rough, measurable surface. Alternatively, a random surface artefact is suggested. This thesis therefore proposes a novel method for FVM resolution determination with random surface artefacts.

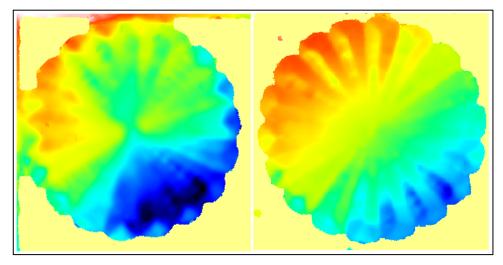


Figure 9: A Siemens star artefact, measured with FVM using 20x (left) and 50x (right) objective lenses. FVM failed to reconstruct the surface of the artefact.

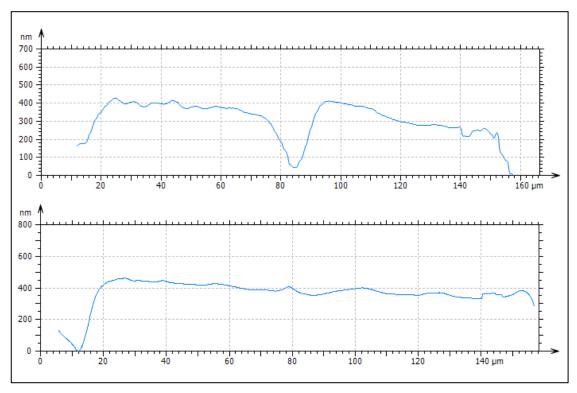


Figure 10: Profiles extracted through the petal of the Siemens star artefact, using FVM 20x (top) and 50x (bottom) objective lenses

2.6 Focus variation microscopy

There are several standard methods available to measure surface texture, one of which is focus variation microscopy (FVM). FVM is a software technology used for operating

optical instruments for surface texture measurements. FVM can provide multi-measurements of surface texture in both 2- and 3D. Danzl, Helmli et al. (2009) and Alicona (2015) stated that FVM can measure the roughness, wear, form and welding spots inspection. This makes FVM a reliable measuring tool that can be used in both industry for quality of products and in the laboratory for research and development. FVM has been defined in (ISO25178-6 2010, ISO25178-606 2015) as a 'surface topography measurement method whereby the sharpness of the surface image (or another property of the reflected light at optimum focus) in an optical microscope is used to determine the surface height at each position along the surface'. This definition emphasises that the FVM method only works with optical instruments to measure surface topography and the data is collected from the reflected light of the optical microscope.

The FVM is developed in several stages until the launch of the final version in the mid to late 1980s (Grossmann 1987, Pentland 1987, Helmli, Hiersemenzel et al. 2012, Hiersemenzel, Singh et al. 2013). The term 'focus variation' was based on a method called 'shape from focus' (SFF) (Hiersemenzel, Singh et al. 2012) – the predecessor of the FVM. The final technique was then commercially deployed as an instrument with hardware and software for surface topography measurements. Hiersemenzel, Singh et al. (2013) mentioned that that FVM was initially developed from 'depth of field', with the final development an accepted improvement of the technology capable of capturing 3D data (with colour) using a specific algorithm at the vertical axis.

2.6.1 FVM working principle

The optical instruments for areal surface topography measurements are similar in their components, but different in working methods. For example, optical instruments have light and different magnifications to measure surfaces. Different sources provide explanations on how the FVM functions (Danzl, Helmli et al. 2009, Danzl, Helmli et al. 2011, Leach 2011, Hiersemenzel, Singh et al. 2013, Tian, Weckenmann et al. 2013, ISO25178-606 2015, Moroni, Syam et al. 2015). A full FVM measurement can be completed when the 3D information of measuring surface is presented.

FVM working principle starts from a white light source passing to the splitting mirror through an optical tube. Then, the splitting mirror guides the white light towards the objective lens that measures the sample's surface. When focused on the sample surface, the white light is reflected by the surface in different directions. Some of the reflected light from the measured sample is captured by the objective and back again through the optical tube to the image sensor after passing a tube lens. It is important to note that

the behaviour of reflective light from the sample's surfaces depends on the type of surface. For example, a diffuse surface type causes all light to be strongly reflected in different directions, whereas a specular surface reflects light in one direction. A charge-coupled device (CCD) sensor, which is located behind the tube lens, then gathers and sense the reflected light. The focus variation value then can be calculated for the formed image. Figure 11 shows the working principle of FVM. The ring light can also be used with FVM to allow measurement of slope surfaces that exceed 80°. This option is an advantage for FVM over other optical measuring instruments. A slope angle of more than 80° will prevent the reflected light from coming back to the lens opening (lens aperture) so that there is no light coming to the image sensor, for example, the numerical aperture of 20× objective lens. Other interferometer-based instruments cannot use ring-light because the ring light does not pass through a reference lens as happens in the axial light system. In an interferometer-based instrument, a reference light is required to create interference fringe from where a surface height can be inferred.

3D surface reconstruction is performed during a measurement by capturing a stack of images continually along the vertical movement of the precision optics head. Changing the focus can affect the contrast on the CCD sensor. The contrast analysis evaluates the variation of focus for each pixel in each image using an algorithm. The sample can be measured when the focus position become in focus (see Figure 12). Repeating this process in each lateral position allows one to measure the sample topography in the range of the objective field of view. This process converts 2D information into 3D, including colour imaging and depth information. Figure 12 shows the 3D surface reconstruction process from a stack of images of FVM.

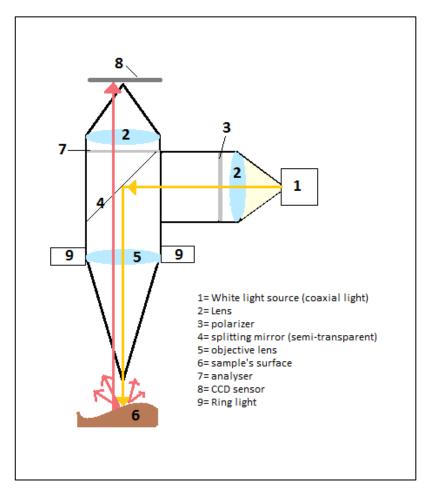


Figure 11: FVM schematic diagram

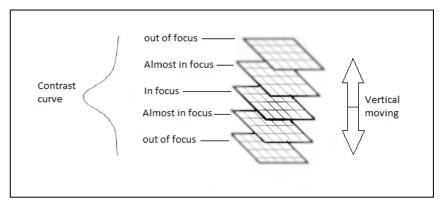


Figure 12: Evaluation process

2.6.2 FVM components

Optical system

According to Vernhes, Bloch et al. (2008), the optical system is the main component of the FVM that confers its precision and includes different lens systems. It is located in the

main head of the FVM and can move vertically to elicit the measurement process. In addition, the lens systems require different objectives to allow for measurements of different resolutions (Vernhes, Bloch et al. 2008, Danzl, Helmli et al. 2009, Danzl, Helmli et al. 2011, ISO25178-606 2015). These objectives differ depending on the measuring field of view and required resolution.

Charge-coupled device (CCD) sensor

The CCD is located at the optics system of the FVM (number 8 in figure 6). The CCD collects the reflected light from the measured surface to analyse the data and the sensor must have two characteristics – high spatial resolution and high radiometric resolution – to distinguish between in- and out-of-focus (Leach 2011). The high spatial resolution minimises the calculation region of the focus and the radiometric resolution improves calculation of the focus of low contrast samples. Without these characteristics, the capability of FVM to reconstruct a 3D surface is limited.

Light source

The measurement process begins from the emitted light source, located in the optical system of FVM – as previously mentioned. Leach (2011) stated that the light source confers quality of the FVM measurement. The light source has been defined in ISO25178-606 (2015) as a 'source of light containing a continuum of wavelengths in a predefined spectral and spatial range'. The FVM can use different light sources, with the illumination type including coaxial light emitted through the optical train and/or from the side called ring light (Danzl, Helmli et al. 2011, Hiersemenzel, Claverly et al. 2013, ISO25178-606 2015). In addition, the light can be external to the measuring instrument (ISO25178-606 2015). The choice of illumination depends on the measuring surface; the ring light can provide more information from the surface by increasing the capability of measuring high slope surfaces so as to exceed 80° and overcome the limitation (Danzl, Helmli et al. 2009, Leach 2010, Danzl, Helmli et al. 2011, Hiersemenzel, Claverly et al. 2013, Helmli, Danzl et al. 2014, Leach 2014).

It should be noted that using different illumination types results in different forms of light projection – needed to measure different sample types and to achieve a high contrast image by the CCD (Leach 2011, Macdonald 2014). The different forms of light projection, for general optical instrument, include coaxial illumination, ring light, diffuse light, dark field light or point illumination (Figure 13). Using these different forms of light

projection overcomes measurement limitations associated with surfaces with different reflection properties (Leach 2011).

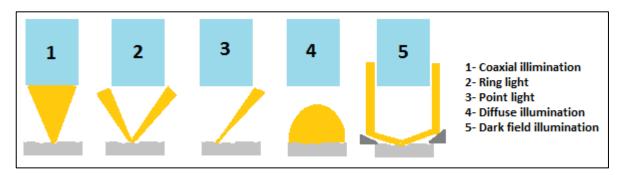


Figure 13: Different types of illumination

Light-emitting diodes (LEDs) are used in the FVM; LED light allows the CCD to detect colour and has the benefit of stability and a long lifetime (Leach 2011). However, halogen bulb light can also be used as light source in the FVM (Hiersemenzel 2013). A polarizer (no. 3 in figure 11) generates the polarized light required for illumination and the analyser (no. 7 in figure 11) filters the reflected light from the sample (Leach 2011). The polarizer is located in the instrument before the light reach the sample, whereas the analyser is reached after the light is reflected to CCD sensor. Polarization helps to reduce the specular components that affect the CCD sensor (SYAM 2014); this is useful when measuring a highly reflective surface. ISO25178-606 (2015) defines polarization as a 'method which allows one to filter out light waves in certain polarization states by using special optical elements called polarizers'.

Objectives

The objectives are connected to lenses in the optical system and used to capture the reflected light from the sample and magnify a measuring area. The FVM uses different magnification lenses to make measurements, ranging from $2.5\times$, $5\times$, $10\times$, $20\times$, $50\times$ and $100\times$. Each magnification has a different resolution, objective's numerical aperture, depth of field, working distance and field of view (Vernhes, Bloch et al. 2008, Danzl, Helmli et al. 2009, Hiersemenzel 2013, Macdonald 2014). Table 4 shows the FVM objective ranges with their measuring field of view and numerical aperture. When the magnification is high, the measurement field of view is reduced and good vertical resolution is achieved (Leach 2011, SYAM 2014). The numerical aperture is different for each magnification. The numerical aperture can determine a large slope angle on a measured surface. The depth of field can be decreased when using a low magnification lens. It is, therefore, important to choose the correct magnification lens for a particular

measurement to efficiently obtaining high quality data. For example, using a high vertical resolution increases the scan time.

Table 4: The FVM objective's field of view

Objective's range	Measuring field of view	Numerical aperture of
	/mm	objectives
2.5×	5.63 x 5.63	0.075
5×	2.82 x 2.82	0.15
10×	1.62 x 1.62	0.3
20×	0.81 x 0.81	0.4
50×	0.32 x 0.32	0.6
100×	0.16×0.16	0.8

Driving unit

The driving unit of the FVM (sometimes called the control unit) is responsible for the vertical and lateral movements (X, Y and Z axes) and is vital for measurement accuracy and reliability of data. The vertical direction of movement of the optical system is carried out automatically and accurately (Hiersemenzel 2013). Moreover, the driving unit is responsible to vertically scan a surface and also to move a sample in lateral (x-y) direction. The movement required depends on the measured sample and the objective. For example, the vertical direction should remain constant when the measured table moves in the lateral direction during the measurement. Although the range of movement in the X, Y and Z planes in the FVM is limited $(100 \times 100 \times 100)$ mm (Danzl, Helmli et al. 2009, Sun and Claverley 2015, Scherer 2016), it allows measurements to be taken at different positions and in different directions. However, vertical and lateral movements cannot be performed simultaneously.

2.6.3 Advantages of FVM over other optical measuring instruments (Alicona, 2015):

- 1. FVM can collect the depth information with true colour registration of the surface.
- 2. Measuring form, position, roughness and dimensions in one system, the gap between classical surface metrology and measuring technology of 3D coordinates is closed in FVM.
- 3. Ring light allows FVM to measure high slope surfaces that exceed 80°.

2.6.4 FVM limitations

There are limitations to FVM that can prevent measurements of some types of surface texture. For instance, measurement of smooth (small local roughness) and/or transparent surfaces is impossible with the FVM (Danzl, Helmli et al. 2009, Danzl, Helmli et al. 2011, Giusca, Claverley et al. 2014, SYAM 2014, ISO25178-606 2015). Thus, any surface that does not meet this requirement tends to be difficult to measure. A surfaces of minimum roughness with Ra <10 nm at a wavelength cut-off of λc = 2 μ m, for instance, is difficult to measure using the FVM (Danzl, Helmli et al. 2011, SYAM 2014, ISO25178-606 2015). It is, therefore, preferable to use a rough surface when using the FVM so as to avoid this limitation. Moreover, the image contrast of the measured surfaces must be high enough for the CCD sensor to differentiate a pixel with respect to its neighbour pixel. Smooth or highly polished surfaces tend to have a low contrast, as captured during vertical scanning. The FVM calculates the focus curve at each position in the stack of images contain a peak of most focused position (see Figure 14). This peak can be detected by using maximum point, polynomial curve fitting or point spread function curve fitting methods (Leash, 2011). The information about these methods is presented in Table 5. A depth map can be available when all lateral positions of the CDD sensor perform the maximum detection.

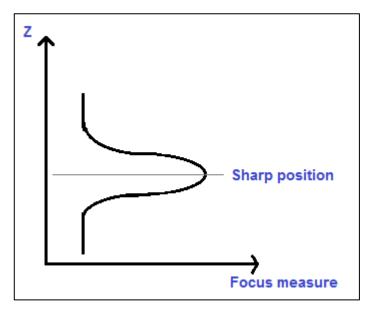


Figure 14: The focus curve

Table 5: Methods of peak detection for focus curve

Methods	Description	Advantage	Disadvantage	Formula
	The calculation of the			
Maximum	depth value is out of the	Fastest	Lowest	(3) Depth=arg(max Fz)
point	index of the largest focus	method	accuracy	For $Z1 \le Z \le Zn$
	- Using the left and right			
	points that are around the	Higher		$(4) P(z) = az^2 + bz + c$
Polynomial	maximum focus point to fit	resolution		(5)
curve	the Polynomial curve by	of the	***	$min_{a,b,c} \sum (F_z - [az^2 + bz + c])^2$
fitting	least square technique (4)	depth		z1≤z≤zn
	- The maximum of fitted	value		(6) $\hat{p}(z) = 2az + b = 0$
	the polynomial in (5)(6)			$(7) Z_{maximum} = -\frac{b}{2a}$
	can be calculated using the			
	coefficients <i>a</i> and <i>b</i> in (7)			
Point	The measured focus values			
spread	can fit the point spread	Highest	Slowest	
function	function to calculate its	accuracy	method	*****
curve	maximum			
fitting				

As mentioned, it is impossible to measure transparent surfaces. Bello, Verveniotou et al. (2011) and Leach (2011) argued that a replica coating material allows the FVM to measure transparent surfaces, as it copies these surfaces. In this case, the FVM can easily collect data from these surfaces. However, Macdonald (2014) claim that it is not always possible to use this replica material as some objects are difficult to replicate and modify. The differences in the surfaces are at the nanoscale; thus, the measurement must be sufficient to capture the variations. Using replica materials may therefore not always be a good choice as the accuracy of measurement data may be affected. To conclude, although an alternative to measuring smooth or transparent surfaces, replica materials may not always be applicable for some surfaces.

Chapter three: The measurement artefacts

3. Measurement artefacts

The chapter presents the artefacts used in the research project. Different measuring artefacts have been used in the experiments of determining the MCs for FVM. The details of the artefact used in the project are presented in the following.

3.1 Measurement noise and Residual flatness artefacts

Two artefacts with different roughnesses are measured in different experiments of measurement noise. One artefact is an optical flat with transparent surface and the other has a surface of suitable roughness. The transparent surface cannot be measured by FVM due to the previously mentioned limitation, which is solved by applying a process to replicate the surface and allow measurements to be taken. The replica material is a silicone casting made from polyvinylsiloxane material. The replica can be produced using cartridges that contain a compound of the polymer and curing agent mixture. This compound can be mixed together automatically in a disposal nozzle during the application (Gasparin et al., 2011). The negative-mirror of a surface can be produced. The replica can be applied directly without any requirement for bubble removing. The Sa value of the replica material is (0.0138) µm compare to (0.010) µm Sa value of optical flat. The optical flat artefact and its replica are shown in Figure 15. The other standard flat surface artefact is called a Halle flat surface and the artefact is presented in Figure 16. This standard Halle flat artefact has been used in the experiment of measurement noise and residual flatness determination. The standard Halle flat artefact (Line of products: KNT 4080/03) is made of stainless steel material with dimension of $(40 \times 20 \times 11.3)$ mm. The measuring area contains six grooves of different depths.

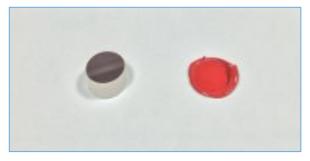


Figure 15: The optical flat artefact (left) and its replica (right)

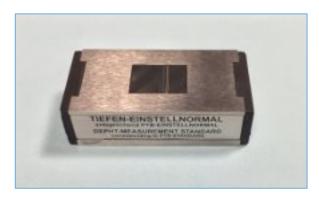


Figure 16: The Halle flat artefact

3.2 Amplification, linearity and perpendicularity artefacts

3.2.1 cross grating artefact for multi-image field measurements

The determination of the lateral amplification, linearity and perpendicularity characteristics requires a calibrated material measure in the form of a two-dimensional (2D) cross-grating (ISO25178-6 2010). The cross-grating can be used to establish the scales of the x- and y-axes. FVM cannot measure commonly available cross-gratings that are smooth (Ra<10nm). Therefore, a new cross-grating artefact that can be measured with FVM needs to be designed and manufactured to calibrate the lateral performance.

The proposed cross-grating artefact has hemispherical groove features (called "calottes" from now onwards) produced by a Kern Evo high-precision micro-milling machine from a block of stainless steel (grade 303). The artefact design is a square block of size of 28 mm with 5 mm thickness, and contains thirty-six calottes with nominal diameters of 0.5 mm. The nominal distance between two calottes is 4 mm. The artefact is designed to capture the scale error of the xy-stage for measurements both with and without stitching, and is presented in Figure 17, which shows the nominal length and thickness of the artefact.

Firstly, a face milling process, using a 6 mm diameter carbide end mill, was applied to flatten the top surface of the block (see Figure 18). The spindle speed and the feedrate of the face milling process were 5000 rpm and 300 mm per minute, respectively. Secondly, the calotte features are machined by a 0.5 mm diameter carbide ball nose mill with the same spindle speed and a federate (see Figure 19). The final surface texture for the top face of the artefact is achieved with a lapping process using a Kemet LM15 lapping machine. Figure 20 shows the Kern milling machine used to make measuring artefact. The artefact is made of stainless steel to create a surface with texture that complies with the FVM requirement. Figure 21 shows the manufactured cross-grating

artefact. The Sa of the manufactured artefact for the measured surface is (0.357±0.004) μ m using nesting indices of S-filter = 2.5 μ m and L-filter = 250 μ m.

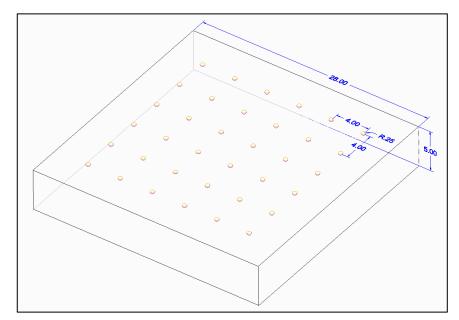


Figure 17: The artefact design.



Figure 18: carbide end mill tool used to flatten the top surface of the artefact.

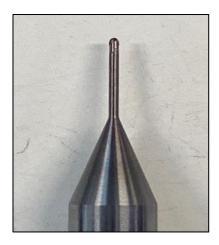


Figure 19: Ballnose tool used to produce the callotes.



Figure 20: Kern milling machine.

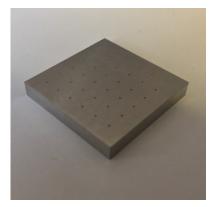


Figure 21:The manufactured artefact.

3.2.2 cross grating artefact for single image field measurements

Another cross grating artefact has been designed and manufactured to determine the amplification coefficient, linearity deviation and perpendicularity characteristics for single image field measurement. This cross grating artefact is stainless steel block containing thirty six hemispheres. Each hemisphere has 0.5 mm diameter and 0.75 mm for the distance between two centre hemispheres. The dimensions and manufactured of this cross grating artefact are shown in Figure 22 and Figure 23, respectively. Same manufacturing process of making first cross grating artefact for multi image field measurement has applied on this artefact. The differences between both artefacts are only in the measurement dimensions. The dimensions of this cross grating artefact are smaller than the previous cross grating artefact for multi image field measurement.

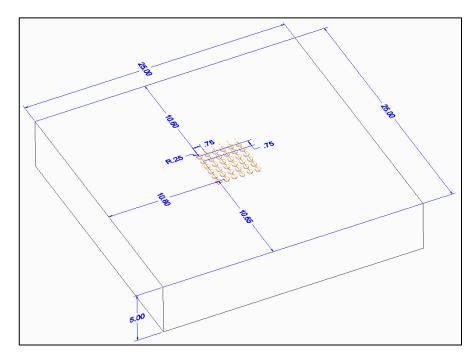


Figure 22: The design of the second cross grating artefact

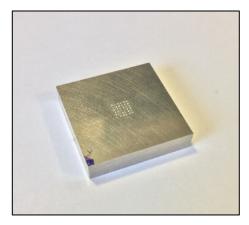


Figure 23: The manufacturing second cross grating artefact

3.2.3 Step height artefact for Vertical scale measurement

The step height artefact is used in this experiment for the error of Z axis of amplification coefficient and linearity deviation characteristics. The step height artefact has made from stainless steel containing five slots with different distance. The depth of each slot is different starting from 0.10 mm and increase 0.10 mm until the last slot. The distance between each slot is 0.70 mm. The kern machine that has made the cross grating artefact is also used to make the step height artefact. Figure 24 and Figure 25 show the design of step height with the dimensions and the manufactured artefact.

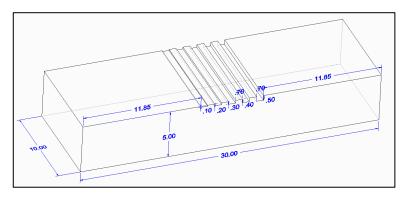


Figure 24: The design of step height artefact

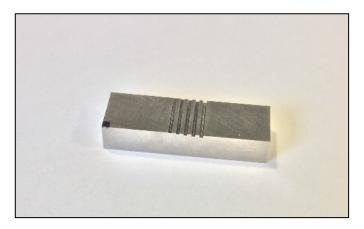


Figure 25: The manufactured step height artefact

3.2.4 Single image field artefact

The artefact is a square block of size of 15 mm with 5 mm thickness. Six slots in each X and Y directions contain thirty-six intersections with nominal diameters of 0.02 mm. The nominal distance between two intersections is 0.07 mm. Figure 26 and Figure 27 show the designed and manufactured artefact. The stainless steel artefact (grade 303) is

manufactured using Kern Evo high-precision micro-milling machine. Figure 20 presents Kern milling machine used for making artefact. The top surface of the block is flatten using 6 mm diameter carbide end mill. A sharp scraping tool carbide material is used to full depth of slot at feed rate of 40 mm/min. Figure 28 shows a scraping tool used to make full depth of slots. The thirty-six slot intersections have been measured to determine the error of X and Y directions. A 2D height map of measured slot intersections with FVM is shown in Figure 29. The artefact features in Figure 29 are not deterministic. Therefore, the difficulties of manufacturing small features may due to tool wear during scraping or material sticking on the tool.

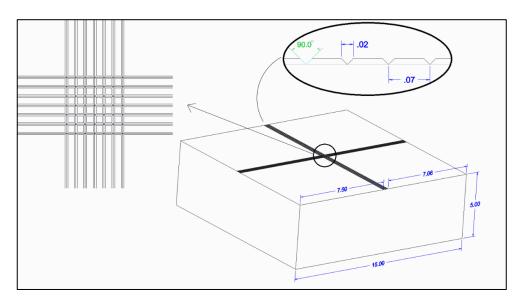


Figure 26: The design of 3rd artefact

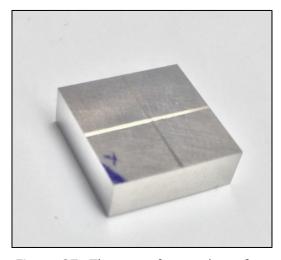


Figure 27: The manufactured artefact



Figure 28: A scraping tool

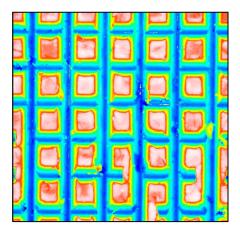


Figure 29: 2D map of slot intersections.

3.3 Topographic spatial resolution artefact

The experiment determines the LPL of topographic spatial resolution using random rough surface artefacts that can be measured by FVM. The artefact used here is a block of stainless steel (grade 303), with six rectangular grooves of the same size on the top. The dimensions are 40×20 mm, 5 mm thick and 30 mm for the groove size. The average Sa value on the groove surface is $0.162~\mu m$ (Gaussian filter with S nesting index of 2 μm and L nesting index of 0.088~mm). The artefact is made by an electrochemical jet machine (EJM), that removes the surface material using an electrolyte jet, instead of conventional tools (Mitchell-Smith and Clare 2016). When an electrical potential is applied between the electrolyte nozzle and work surface, an anodic dissolution occurs, thereby removing the surface material. Figure 30 shows the EJM used to manufacture the artefact.



Figure 30: Electromechanical jet machine

A tape mark was placed on the block top to measure the same areas of each groove for both the Zygo CSI and FVM instruments. Figure 31 shows the artefact used in the experiment.

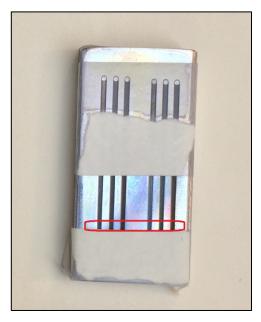


Figure 31: The resolution artefact. The red rectangle shows the groove measuring areas

Chapter four: Measurement noise experiments

The thesis aims to investigate the traceability framework by determining the metrological characteristics (MCs) for a focus variation microscopy (FVM) instrument, as an optical areal surface texture measuring instrument.

The MCs of measurement noise and measurement repeatability can be determined by doing four experiments. The research aim is addressed by determining the measurement noise of FVM using the measurement of a replica of an optical flat, the determination having different measurement parameters, that are illumination, contrast and brightness parameters and finding non-linearity of a vertical scale.

The experiment on a replica of an optical flat measurement addresses all the three questions. In this experiment, the MC can be determined through the measurement noise and measurement repeatability. The replica of an optical flat can be measured in the determination of measurement noise for FVM. Good practical procedures to determine the MC with the replica of an optical flat are presented in the experimental methodology. In this stage of performing the experiment, it can be predicted that the noise is stable between different vertical heights and objective lenses. The variable of vertical height can be kept constant as contrast and exposure time vary.

Regarding the determination of measurement noise with different measurement parameters (illumination, contrast and exposure time parameters), these experiments also address all three research questions. A Halle flat surface artefact can be measured to determine the measurement noise for FVM. Good practical procedures to determine the MC with different parameters using the Halle flat surface artefact have been followed throughout. In this stage, it can be predicted that changing the parameters of illumination, contrast and exposure time does not affect the noise. In these experiments, the variables of the parameters of illumination, contrast and exposure time were kept constant and the vertical height varied.

The finding of non-linearity vertical scale for measurement noise determination addresses all three research questions. The measurement noise was determined for different vertical heights and objective lenses. The Halle flat surface artefact can be measured for measurement noise determination and good practical procedures were followed throughout the experiment. The noise can be predicted in this stage as constant for different vertical height scales. The variable of different vertical height is constant in this experiment and the variable of the contrast and exposure time of different objective lens varies. By doing these experiments of determining the measurement noise, the research aims can be achieved, and the questions answered.

4. The experiments

The measurement of noise in the FVM calibration is important to study instrument's performance in terms of its measuring accuracy. The measurement noise data are obtained using a FVM G5 instrument. The noise measurement experiments have been implemented in different ways to study the effect of different material measures and different measurement parameters to the calculated measurement noises. The experiments of measurement noise are performed using different experiment designs, such as measuring the replica of an optically flat artefact, measuring the flat surface artefact, investigating the effect of contrast and brightness (exposure time) and the effect of different illumination types. The hypothesis for the replica of an optically flat artefact is: 'the noise is stable for different vertical heights and with both objectives because any flatness errors are from the vertical stage error'. The experiment will determine the noise between two objective lenses for different vertical heights. The objective lenses of $50 \times$ and $100 \times$ and the vertical heights of 5, 35, 40, 55, 70 and 85 mm will be used in the experiment.

The hypothesis of investigating the effect of contrast and brightness (exposure time) is: 'changing the contrast and brightness does not affect the noise in both objectives'. The experiment will determine the noise between two objective lenses for different vertical heights between two different parameters of contrast and brightness (exposure time). The hypothesis of investigating the effect of different illumination types is: 'changing the illumination types does not affect the noise'. The experiment will determine the noise between two different illumination types, coaxial light and polariser for different vertical heights. The hypothesis of measuring the Halle flat surface artefact is: 'the noise is stable for different vertical heights'. The experiment will determine the noise between two objective lenses of $50 \times$ and $100 \times$ at different vertical heights.

Three analytical methods are used to analyse the experiment results, namely subtraction, averaging and measurement repeatability. The values of measurement noise (Sq_{noise}) are calculated three times to better estimate the noise because averaging will reduce random variations in the calculated results. Some measurement noise experiments are conducted at different vertical heights that are from 1 mm to 100 mm. Figure 32 shows the vertical height scale of the FVM instrument. The schematic diagram in Figure 33 shows the vertical height and its relation to sample and stage position. From Figure 33, it can be seen that the height can be adjusted vertically and the stage for the sample is positioned at a suitable distance to allow the objective lens to capture the

data. For example, the sample's stage position for 0 mm vertical height is different from the sample's stage position for 50 mm vertical height.



Figure 32: The vertical height scale of the instrument

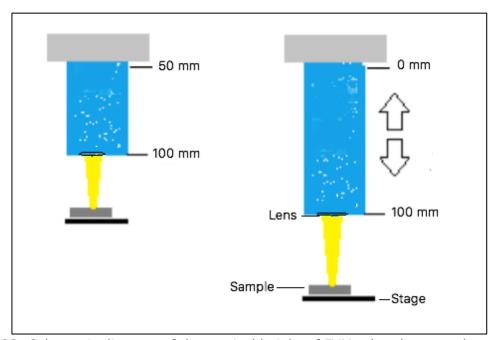


Figure 33: Schematic diagram of the vertical height of FVM related to sample and stage position.

The data analytic process is implemented using MountainsMap surface metrology software (Surf). In the subtraction method, the data of two measuring surfaces are subtracted. The levelling process is applied on the subtracted surface to obtain the Sq value. The Sq_{noise} value was calculated by using the obtained Sq value in formula one (see analytical background section on page 23).

$$(Sq_{noise} = \frac{Sq}{\sqrt{2}}) \tag{1}$$

The calculation was repeated three times with different measuring data of Sq to obtain the best estimation and reduce the error. Figure 34 shows the subtraction process of the replica of the optical flat surface artefact using Mountainsmap. For averaging purposes, the data of 2, 4, 6, 8 and 10 measured surfaces are averaged. The averaged surfaces are levelled, and the threshold set to remove the spikes from the averaged surface (Figure 35 shows the averaged process from Mountainsmap). Then, the Sq value can be obtained after the thresholding process and used in the following formula. The Sq_{noise} results from the average method were calculated using formula number two (see analytical background section on page 23).

$$Sq_{noise} = \sqrt{\frac{Sq^2 - Sq_{mean}^2}{1 - \frac{1}{n}}} \tag{2}$$

The Sq value is non-averaged data and the Sq_{mean}^2 is the value of a number of averaged Sq data, which represented by n.

This calculation is repeated three times using different Sq data to obtain the best estimation and reduce the error. For measurement repeatability, the Sq value is obtained from Mountainsmap by levelling and setting the threshold for the measured surface. Figure 36 represents the process of obtaining the Sq value from the measured surface. The SD result is obtained from calculating ten Sq data. The calculation is repeated three times to obtain the best estimation and reduce the error. All the calculations of subtraction, averaging methods and measurement repeatability are presented in figures using minitab software. It is important to mention that the analysis procedures using Mountainsmap are applied on all the following experiments of measurement noise. Details of the design for each experiment to measure noise with their results and discussions are provided below. The measurement processes are applied under normal conditions of temperature and humidity that are $20\,^{\circ}\text{C} \pm 1\,^{\circ}\text{C}$ and $50\% \pm 5\%$, respectively.

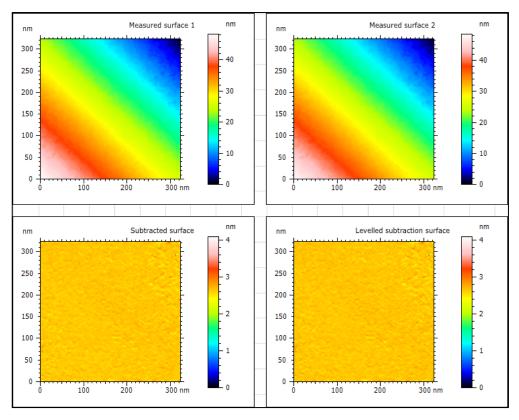


Figure 34: Subtraction measuring surface process using Mountainsmap

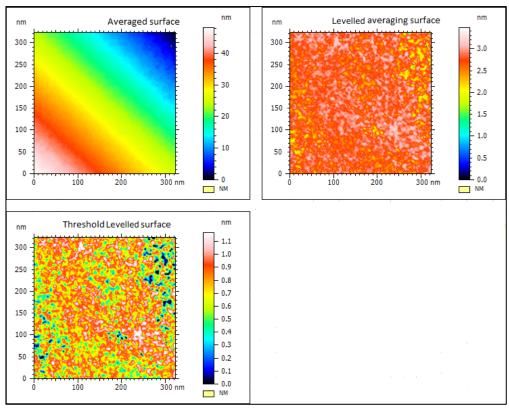


Figure 35: Average process using Mountainsmap

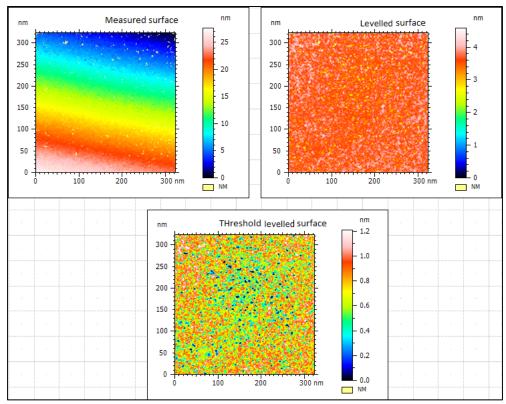


Figure 36: Measurement repeatability using Mountainsmap

4.1 The replica of flat surface artefact

Method

This experiment is designed to find the measurement noise for different objectives and vertical heights by measuring the replica of the optical flat surface. The hypothesis is 'the noise is stable for different vertical heights and with both objectives'. Two different magnification lenses of FVM, $50\times$ and $100\times$, are used to collect the data. Twenty measurements are collected sequentially in the same area of the surface at different levels (5 mm, 35 mm, 40 mm, 55 mm, 70 mm and 85 mm) of the vertical height range of the FVM instrument. All measuring data for different vertical scale are collected in one session measuring time. The settings for the experiment are presented in Table 6. From Table 6, the contrast and exposure time are chosen to assist in gaining the image data from both objectives. The contrast and exposure time are different. The contrast in this experiment is chosen to make the measuring sample visible and the exposure time is set to make the image bright when measuring. When the contrast value becomes higher, it leads to a long measuring time. Therefore, the contrast and exposure time are chosen to collect good measurement data within short time.

Table 6: Settings for the experiment process

Lens	Height range	Number of	Image	Exposure time	Artefact
	/mm	measured surface	Contrast	/µs	
50×	5, 35, 40, 55, 70,				Replica of
100×	and 85 /every	20 / every height	1	500	optical flat
	lens				

The procedure of analysing the subtraction method, averaging method and measurement repeatability using Mountainsmap software are explained in the general methodology information (see section 4 The experiments). The average of (2, 4, 6, 8) and (2, 4, 6, 8) and (3, 4, 6, 8) and (3, 4, 6, 8) and (3, 4, 6, 8) are surfaces is calculated by using the average method. This process is conducted to find out the differences between the noise results of the averaging surface. The repeatability measurement is applied under the same measuring conditions, but with different height levels, namely (3, 4, 6, 8) mm, (

Results

The subtraction method of the replica artefact has shown some interesting findings. There are statistically significant differences in the noise for different vertical heights. In terms of the $50 \times$ magnification lens (see Figure 37), the noise varies between the different vertical heights. The 40 mm level of vertical height has the highest noise, while the 5 mm level has the lowest noise. Figure 38 shows the noise of different vertical heights using the $100 \times$ magnification lens. The highest noise appears at the 55 mm level of vertical height, while the 85 mm level shows the lowest noise. The interval results in Figure 37 and Figure 38 are one sigma calculation of standard deviation divided by square root of three i.e. (number of measuring data).

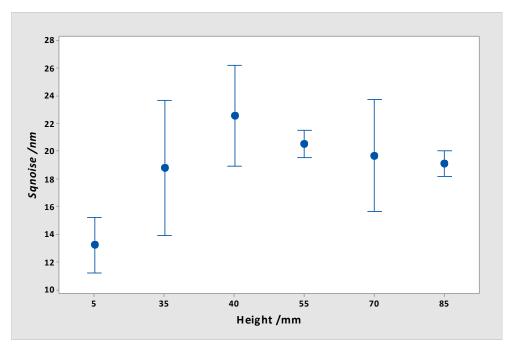


Figure 37: Results of subtraction method for 50× objective lens

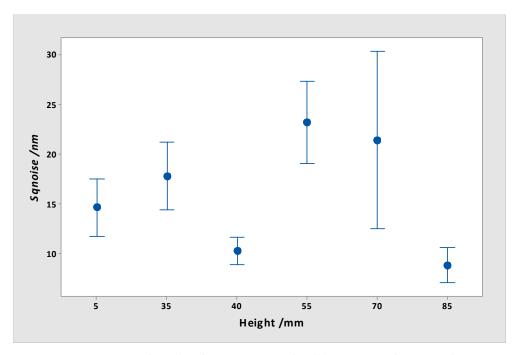


Figure 38: Results of subtraction method for 100× objective lens

The results of the average method are similar to the subtraction method for instrument behaviour. The noise varies between the vertical heights in both objectives. In the $50\times$ and $100\times$ objective lenses, the noise is reduced in each vertical height when the number of averaged surfaces increases. However, at level 55 mm in both objectives, there is an assignable different behaviour that could be related to the vertical stage non-linearity. Figure 39 shows the noise for the average method for the $50\times$ objective lens. The noise

for the average method for 100× is shown in Figure 40. The interval results in Figure 39 and Figure 40 are one sigma calculation of standard deviation divided by square root of measured surface i.e. (number of measuring data).

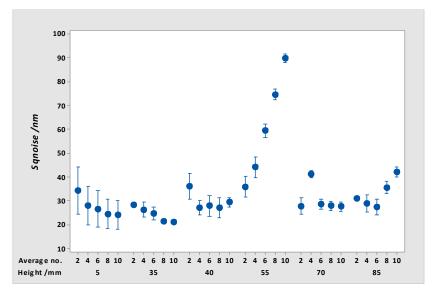


Figure 39: Results of average method for 50× objective lens

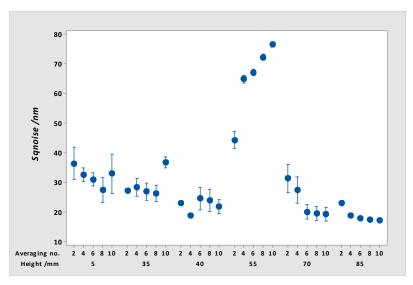


Figure 40: Results of average method for 100× objective lens

The measurement repeatability results agree with the subtraction and averaging methods. The results of different vertical heights are the standard deviation of 10 single measured surfaces. The highest noise of the $50\times$ objective lens at 40 mm vertical height, and the 60 mm level shows the lowest noise. Figure 41 presents the results of Standard Deviation for the $50\times$ objective lens. In the $100\times$ objective lens, the highest noise is at 60% level of vertical height and the lowest noise is at 40 mm level. Figure 42 illustrates the results of Standard Deviation for the $100\times$ objective lens. The interval

results of Figure 41 and Figure 42 are one sigma calculation of standard deviation divided by square root of ten surface measured data.

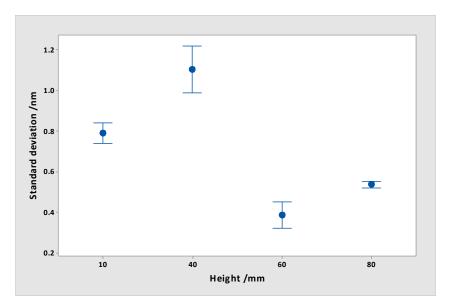


Figure 41: Results of measurement repeatability for 50× objective lens

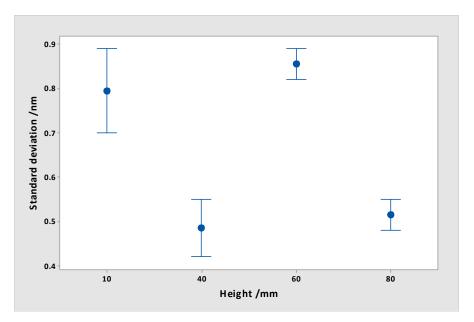


Figure 42: Results of measurement repeatability for 100× objective lens

4.2 The effects of different measuring parameters

4.2.2 Contrast and brightness parameters Method

Experiments have been carried out focusing on the noise between two different settings of the contrast and brightness parameters. The hypothesis is 'changing the contrast and

brightness does not affect the noise in both objectives'. Two objective lenses of $50\times$ and $100\times$ are used to measure the Halle flat artefact. In addition, 20 data are collected for each different setting of contrast and brightness. The vertical range is fixed at 10 mm height. The same vertical and lateral resolutions have been used in both objectives. The details of the experiment are presented in Table 7. From Table 7, the contrast and exposure time are chosen to assist in gaining the image data from both objectives. The contrast and exposure time are discussed in the first measurement noise experiment.

Table 7: Information for the experiment

Lens	Image	Exposure time	Height	Number of	Vertical	Lateral
	Contrast	(Brightness) / μs	range	measured surface	resolution	resolution
	1.10	130				
50×	1.70	90				
100	1.10	130	10 mm	20	10 nm	1.34 μm
100×	1.70	90				

The procedure of analysing the measured data for subtraction, averaging and measurement repeatability using Mountainsmap software is presented in section 4 of this chapter. For the average method, different average surfaces (2, 4, 6 and 8) are calculated in both settings of contrast and brightness. A standard deviation of each objective at different parameters is obtained for the measurement repeatability calculation.

Results

The subtraction method in both objectives has statistically significant difference for noise results. This means that different parameters of contrast and brightness affect the noise of the FVM instrument. The subtraction method results for different contrast and brightness for $50\times$ and $100\times$ objectives are shown in Figure 43 and Figure 44, respectively. The results of the second (2) contrast and brightness settings are higher than for the first (1) contrast and brightness settings in both objective lenses. The interval results in Figure 43 and Figure 44 are one sigma calculation of standard deviation divided by square root of three i.e. (number of measuring data).

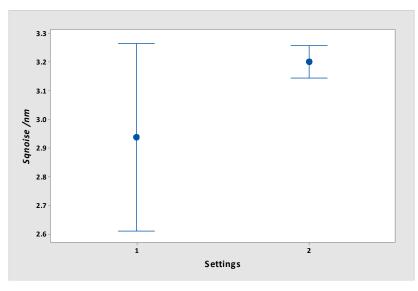


Figure 43: Results of subtraction method for $50 \times$ objective lens (1: first contrast and exposure time setting, 2: second contrast and exposure time setting).

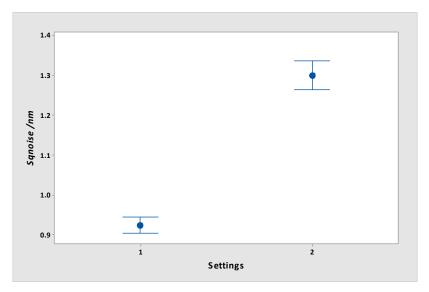


Figure 44: Results of subtraction method for $100 \times$ objective lens (1: first contrast and exposure time setting, 2: second contrast and exposure time setting).

The average method results are limited in this situation and cannot capture the significant difference between two measurement parameters. The noise results are decreased when the number of the averaged surfaces is increased in both settings and objectives. Figure 45 and Figure 46 show the average results of $50 \times$ and $100 \times$ objective lenses. The interval results in Figure 45 and Figure 46 are one sigma calculation of standard deviation divided by square root of measured surface i.e. (number of measuring data).

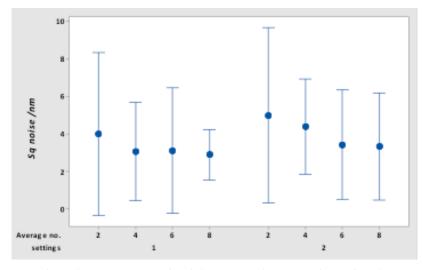


Figure 45: Results of average method for $50 \times$ objective lens (1: first contrast and exposure time setting, 2: second contrast and exposure time setting).

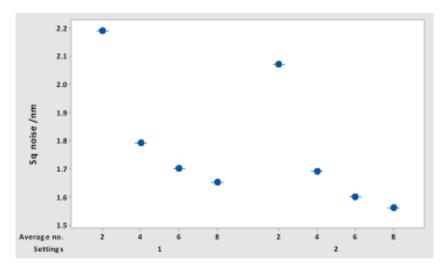


Figure 46: Results of average method for $100 \times$ objective lens (1: first contrast and exposure time setting, 2: second contrast and exposure time setting).

Similar to the results of the subtraction and average methods, the measurement repeatability of the $50\times$ and $100\times$ objective lenses are statistically different between the settings of contrast and brightness. Figure 47 and Figure 48 show the measurement repeatability of the $50\times$ and $100\times$ objective lenses, respectively. From Figure 47 and Figure 48, the interval results are one sigma calculation of standard deviation divided by square root of ten surface measured data.

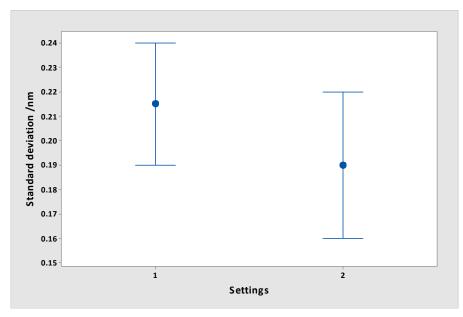


Figure 47: Results of measurement repeatability for $50 \times$ objective lens (1: first contrast and exposure time setting, 2: second contrast and exposure time setting).

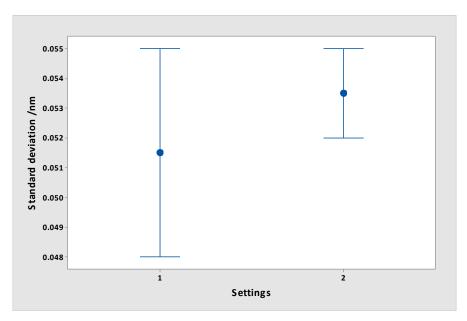


Figure 48: Results of measurement repeatability for $100 \times$ objective lens (1: first contrast and exposure time setting, 2: second contrast and exposure time setting).

4.2.2 The illumination parameters

Method

This experiment is designed to find the effect on the noise that could result from using the polariser. The measurements in this experiment are collected twice with different illumination settings. The first measurement is applied on coaxial light as a normal situation, while the second measurement is performed by using the polariser. These different illumination types apply the same parameters of contrast, exposure time and vertical and lateral resolution. Two objective lenses of $50\times$ and $100\times$ magnifications are used to measure the Halle flat surface artefact. The measurements are conducted at different vertical heights (20 mm, 40 mm, 60 mm and 80 mm). Table 8 shows the information of the experimental design. The contrast and exposure time can be changed separately. The contrast and exposure time are chosen to assist in gaining the image data from both objectives. The contrast and exposure time are discussed in the first measurement noise experiment.

Table 8: Details of the experiment

	Height	Number of	ber of Parameters				
Lens	range	measured	Illumination	Image	Exposure time	Vertical	Lateral
	/mm	surface		Contrast	(Brightness) /µs	resolution	resolution
50×	20, 40,	25 data for	- Coaxial		500 = 50×		
100×	60 and	each height	light	1	80 = 100×	10 nm	1.46 µm
	80		- Polariser				

The procedure of analysing the measured data for subtraction, averaging and measurement repeatability using Mountainsmap software is presented in section 4 of this chapter. Regarding the average method, the surface average numbers are 2, 4, 6 and 8. The standard deviation of calculating the measurement repeatability is applied in some of the vertical heights, namely (20, 40, 60 and 80) mm.

Results

The results of the subtraction method demonstrate that the noise with the polariser is statistically higher than the noise with the normal light condition in both of the objectives. One reason could be with the polarised light is that the light intensity on the CCD image sensor is lower compared to the measurement without polariser filter. The difference between the noise of polarised and normal light is significant in both objectives. Figure 49 and Figure 50 show the subtraction results of the $50\times$ and $100\times$ objective lenses, respectively. The interval results in Figure 49 and Figure 50 are one sigma calculation of standard deviation divided by square root of three i.e. (number of measuring data).

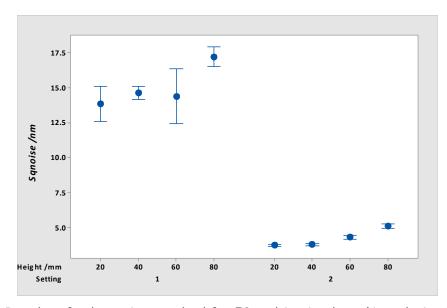


Figure 49: Results of subtraction method for $50 \times$ objective lens (1: polarised, 2: normal light)

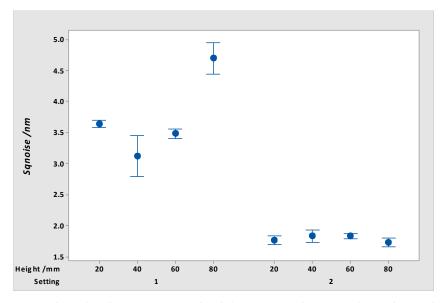


Figure 50: Results of subtraction method for $100 \times$ objective lens (1: polarised, 2: normal light)

The findings for an average method for both light settings in two objective lenses seem to be similar to those for the subtraction method. The noise using the polariser is higher than with the normal light. With the normal light setting, the noise decreases when the number of the average surfaces is increased. Figure 51 shows the average method for $50\times$ objective lens for both light settings. The average method results of the $100\times$ objective lens are shown in Figure 52. The interval results in Figure 51 and Figure 52 are one sigma calculation of standard deviation divided by square root of measured surface i.e. (number of measuring data).

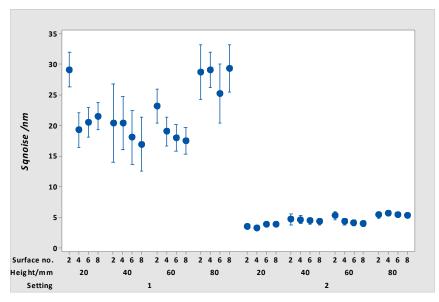


Figure 51: Results of average method for $50 \times$ objective lens (1: polarised, 2: normal light)

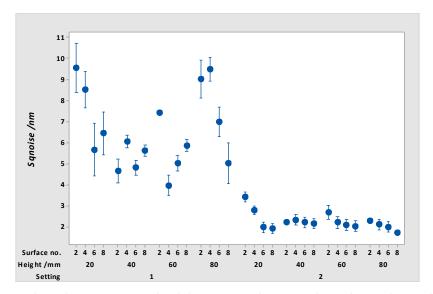


Figure 52: Results of average method for $100 \times$ objective lens (1: polarised, 2: normal light)

The measurement repeatability findings are similar (statistically insignificant) to the subtraction and average methods. The polariser data are higher than the normal light data. The results of measurement repeatability for $50\times$ and $100\times$ lenses are shown in Figure 53 and Figure 54, respectively. The interval results in Figure 53 and Figure 54 are one sigma calculation of standard deviation divided by square root of ten surface measured data.

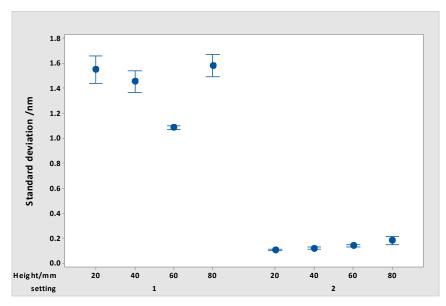


Figure 53: Results of measurement repeatability for $50 \times$ objective lens (1: polarised, 2: normal light)

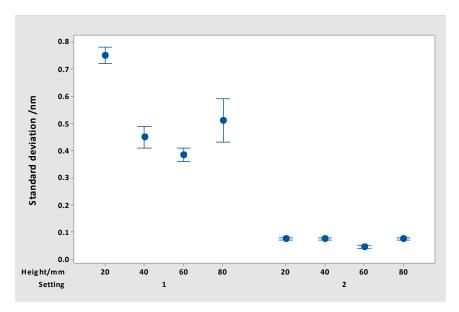


Figure 54: Results of measurement repeatability for 100× objective lens (1: polarised, 2: normal light)

4.3 Discussion

The measurement noise and measurement repeatability are conducted in different experimental designs. The aim of the first experiment is to find the noise between different objective lenses and vertical heights using the replica of an optical flat. The experiment is carried out using two objective lenses, with magnifications of $50\times$ and $100\times$, to measure the replica of an optical flat surface with equal contrast and brightness parameters. Different height levels (5 mm, 35 mm, 40 mm, 55 mm, 70 mm and 85 mm)

of the total vertical scanning range of the instrument are used. The next experiments are conducted between different parameters of the FVM to study the effect of the different parameters on the measurement noise. The aim of the first parameter (contrast and brightness) is to find the effects on the noise of changing the contrast and brightness settings. Two magnifications using $50\times$ and $100\times$ objective lenses have been implemented with the same settings of vertical and lateral resolution. One height range (10 mm) of vertical scanning on the flat surface artefact has been used. Twenty measuring data are collected in each setting for both objectives. In the second parameter (illumination conditions), the purpose is to find the effect of different illumination types on the noise. Coaxial light and a polariser are used. Different height levels (20 mm, 40 mm, 60 mm and 80 mm) of the vertical stage scale have been used in two objective lenses of $50\times$ and $100\times$ magnifications. The results for subtraction and average methods and measurement repeatability have been calculated. At each height level, twenty-five data have been collected in both light settings. The parameters of contrast and vertical and lateral resolution have been fixed for all of the measurements.

The noise is nonlinear between the different vertical heights in both objectives. The finding of nonlinearity of the vertical scale for FVM was not expected when performing the experiment. The nonlinearity of vertical range may be caused by the imperfection of the ball screw of the vertical Z drive. The manufacturer of the FVM instrument confirms that the vertical range varies. i.e. the noise is vary in different height. The interpretation of this difference may relate to the way in which the height range adjust is mounted on the guiding rails and the way in which the drive train is guided. The effects of varying the vertical range of FVM seem to be general as confirmed by the FVM manufacturer. The finding of nonlinearity of vertical scale is very significant for FVM users. Therefore, it is important for the FVM users to recognise the nonlinearity of the vertical scale when using FVM; for example, when measuring at the level that provides low noise. In spite of the fact that the FVM instrument can measure the replica of the optical flat artefact to overcome its limitations, using the replica might not always be appropriate to identify the noise. The findings of measurement noise and measurement repeatability are high. Therefore, the replica may not provide valid results of the noise. According to Macdonald (2014), it is not always possible to apply the replica due to the fact that the surface texture of the original surface can be different at the nanoscale level. The surface should have a roughness of more than 10 nm to allow the instrument to collect the data (Leach 2011). Therefore, there is some doubt about the replica of the optical flat artefact. Due to the fact that the optical flat artefact cannot be measured by the FVM, its replica, which overcomes the instrument limitation, may have an issue in the object modification. The measurement can be obtained from the replica, but it could affect the appropriate results. For this reason, the replica of the optical flat artefact seems to become inappropriate for the measurement of noise.

Regarding the noise difference between contrast and brightness parameters, the findings indicate that the effects on the measurement noise of changing the contrast and brightness are significant in both objectives. These findings are similar to a previous measurement noise experiment (Hiersemenzel 2013). In Hiersemenzel's work, changing only the contrast is not affecting the noise, while changing only the brightness can affect the noise. However, the findings of our experiment indicate that changing the contrast and brightness together can affect the noise significantly. The noise between two settings does not exceed 0.5 nm in both objectives. The changing in the noise may be occurring because of the brightness effect. The contrast and brightness can be related to whether polarised or normal light is being used to obtain the data. Leach (2011) explains that the contrast and brightness settings can assist in gaining the image data. It is clear that changing the settings of contrast and brightness can allow the instrument to collect sufficient data from the surface in the measuring operation. The drawbacks of applying this experiment are related to choosing the appropriate settings to allow the measurements to be collected. Some settings of contrast and brightness create difficulties in measuring the surface in both objectives. In addition, some settings of contrast and brightness can result in a long measuring time.

In the findings of different illumination parameters, using the polariser in the measurement with specific settings of contrast leads to increase the noise. The polarised light can assist in collecting the measurement. Leach (2011) and Nikolaev, Petzing et al. (2016) confirmed that the polarisation can reduce the specular light components that cause a problem for the CCD sensor to collect the data. However, the polarised light will reduce the light intensity to the CCD image sensor and can increase the noise. From the practical point of view, the polariser setting can be used when activated to reduce the specular light from the measuring surface. However, when the polariser setting is changed to a different light setting, it may cause some issues in the measurement. Therefore, the noise can be increased when using the polariser when the measurements in both light situations have used the same measuring conditions. The polariser settings can be made suitable for its work. Using the polariser with a different setting leads to some problems in the measurement. High measurement noise can be an example of the measurement problems.

To sum up, the noise results from the previous measurement noise experiments can be improved when averaging the collected measurement over time due to random noise

reduction. This measurement collection strategy may help in obtaining better measurement noise results. Also, De Groot and DiSciacca (2018) mention that averaging the measurement over time can assist in getting low measurement noise.

Regarding the question of the determination of MCs for FVM, the determination of measurement noise is provided in three measurement noise experimental designs. A flat surface artefact and replica of an optical flat surface artefact are suitable artefacts in this determination. The replica of the optical flat surface is measured due to the FVM limitations of not being able to measure smooth and transparent surfaces. The calibration procedures for FVM through measurement noise determination are explained in the experimental methodologies.

4.4 Detection of stage non-linearity with measurement repeatability

The experiment is focused on detecting a non-linearity signature of the FVM vertical stage using measurement noise and measurement repeatability. Two objective lenses with magnifications of $50\times$ and $100\times$ have been used. The Halle flat artefact was measured at different vertical heights, namely 5 mm, 40 mm, 55 mm, 70 mm and 85 mm. Twenty data were collected for each height in each lens. The contrast and brightness parameters were set constant between the different lenses. Table 9 shows the information for the measurement. The contrast and exposure time are chosen to assist in gaining the image data from both objectives. The contrast and exposure time are discussed in the first measurement noise experiment (see page 60).

Height range for Number of Exposure time every lens /mm Lens measured surface Contrast Brightness / µs Artefact 50× 5, 40, 55, 70 20 data for every 142 Halle flat 1 100× and 85 height artefact

Table 9: Information for the experiment design

All the calculation methods of measurement noise, namely subtraction, averaging and measurement repeatability. The procedure of analysing the measured data for subtraction, averaging and measurement repeatability is presented in section 4 of this chapter. Regarding the average method, different average surfaces were calculated, namely 2, 4, 6, 8 and 10 surfaces. In the measurement repeatability, the standard deviation was calculated for some of the vertical heights, namely 5 mm, 40 mm, 55 mm and 85 mm.

Result

The results of the Halle flat artefact for the subtraction method present a significant difference between $50\times$ and $100\times$ objective lenses. In the $50\times$ objective lens, the 5 mm level of vertical height has the highest noise and the 35 mm level of vertical height has the lowest noise. The results of the subtraction method for the $50\times$ magnification lens are shown in Figure 55. In the $100\times$ objective lens, the 35 mm level of vertical height has the highest noise and the 5 mm level of vertical height has the lowest noise. Figure 56 demonstrates the subtraction method results for the $100\times$ objective lens. The interval results in Figure 55 and Figure 56 are one sigma calculation of standard deviation divided by square root of three i.e. (number of measuring data).

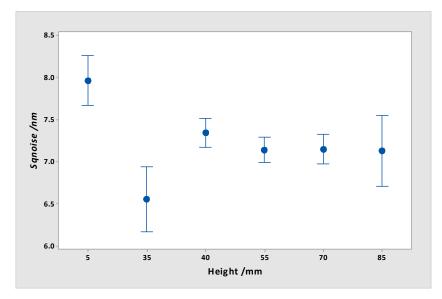


Figure 55: Results of subtraction method for 50× objective lens

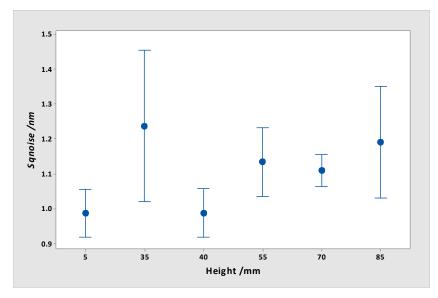


Figure 56: Results of subtraction method for 100× objective lens

The average method findings of the Halle flat artefact show similar results to the subtraction method. For the $50 \times$ magnification lens, the noise is higher at 5 mm height, while the values for the other heights seem to be similar. The findings of the average method for $50 \times$ are shown in Figure 57. In the $100 \times$ magnification lens, the highest noise was at 70 mm level of vertical height and the lowest noise is at 40 mm level of vertical height. The average results of the noise for $100 \times$ are presented in Figure 58. By increasing the number of averaging surfaces, the noise can be reduced with a condition that the surface data has a statistically stationary condition. The interval results in Figure 57 and Figure 58 are one sigma calculation of standard deviation divided by square root of measured surface i.e. (number of measuring data).

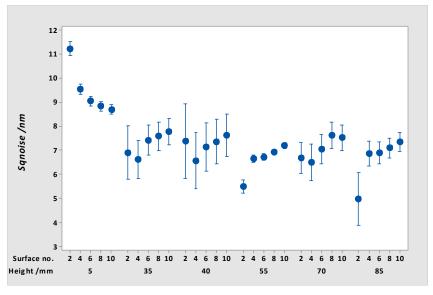


Figure 57: Results of average method for 50× objective lens

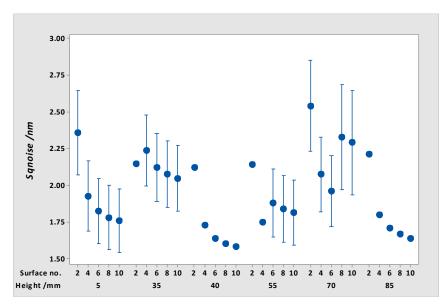


Figure 58: Results of average method for 100× objective lens

The measurement repeatability results are similar to the results of subtraction and averaging methods. Both $50\times$ and $100\times$ objective lenses are non-linear between the vertical heights. A perfect stage should have a constant noise in all of the vertical heights. Figure 59 shows the standard deviation calculation of the $50\times$ objective lens. In comparison, the noise of the $100\times$ objective lens increases when the vertical height increases. The SD calculation of the $100\times$ objective lens is shown in Figure 60. The results obtained in Figure 59 and Figure 60 are the results of standard deviation divided by square root of ten surface measured data.

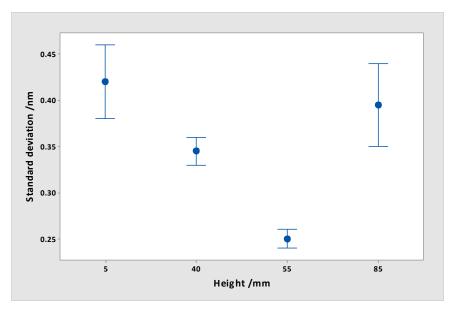


Figure 59: Results of measurement repeatability for 50× objective lens

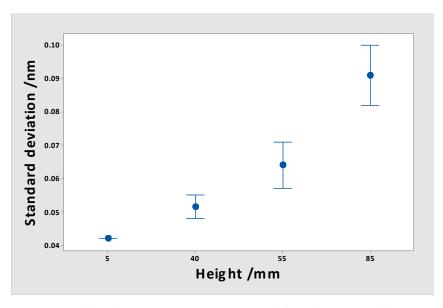


Figure 60: Results of measurement repeatability for 100× objective lens

Summary

This experiment detects the non-linearity signatures of the vertical height for the FVM. Two objectives lenses with magnifications of $50\times$ and $100\times$ have been applied to measure the Halle flat surface artefact with equal contrast and brightness parameters. Subtraction and average as well as the surface topography repeatability methods have been used in the calculation. Different height levels (5 mm, 35 mm, 40 mm, 55 mm, 70 mm and 85 mm) of the total vertical scanning range of the instrument are used.

The noise results show that the vertical stage tends to be non-linear. It is recognised that the nonlinearity of the vertical scale is more significant for FVM users when, for example, measuring at the level that has less linearity. In the $100 \times$ objective lens, the noise seems to increase for both the noise and the measurement repeatability. The noise between the different vertical heights is statistically significant. The manufacturer of the FVM instrument agrees with these findings and confirmed that the change between the different levels of vertical height is significant, and the results of this experiment present a similar idea to that presented by the FVM manufacturer (Alicona 2016). Although these differences are quite small, they can add to the increase of the measurement noise of the FVM instrument. The non-linearity could be caused by the way in which the drive train is guided and how the Z-axis is mounted on the guiding rails. This interpretation seems to be the reason behind the differences in the linearity of vertical height levels. As the FVM manufacturer obtained similar results, it can be confirmed that the effects seem to be general for FVM.

In this experiment, the metrological characteristic can be determined through the measurement noise and measurement repeatability. A Halle flat reference surface artefact is a suitable artefact that can be measured in the determination of measurement noise for FVM. The good practical procedures to determine the MC with the suitable artefact are presented in the experimental methodology.

Chapter five: Residual flatness experiment

The thesis aims to investigate the traceability framework by determining the metrological characteristics (MCs) for a focus variation microscopy (FVM) instrument, as an optical areal surface texture measuring instrument.

The research aim is addressed by determining the residual flatness of FVM by applying two different filters using the measurement of the Halle flat surface artefact (the ISO filter standard and proposed method). One of the MC of FVM can be determined through the residual flatness. Good practical procedures to determine the MC are used throughout the experiment. Applying the filter can be predicted as an important process in the determination of residual flatness. The variables of different filter and objective lenses were kept constant, and contrast and exposure time for different objective lenses were varied in the experiment. The research aims and questions can be achieved by doing the experiment of determining the residual flatness.

5 The experiment

5.1 Method

The experiment is performed to calculate the residual flatness characteristic using different filtering processes. One process follows the ISO instruction and the other is proposed method. The ISO instructions of the filtering process are to use a low pass Gaussian filter as stated in the ISO standard to generate an SF-surface with a cut-off value that is equal to one-tenth of the field of view. Another filtering process (the proposed method) is to multiply the sample distance of the field of view of each objective by ten. The ISO standard requires measurements with a determined specification for sample length and area. This ISO sampling requirement in many cases cannot be satisfied. Therefore, the proposed filter method can be used as an alternative when the sample length or the size of a measured surface area cannot follow the ISO requirements. Two objective lenses with magnifications of 50× and 100× have been used in this experiment. Instrument parameters are fixed to find the differences that may occur between the objectives. The fixed parameters are contrast, brightness, and vertical and lateral resolutions. Only one vertical height range (55mm) has been used. This experiment focuses on the error of the Z-scale. The measuring surface should be flat (Ra>10nm) to achieve the measuring requirements of determining the residual flatness for FVM. Therefore, a Halle standard flat surface (with Sa value is 85.4 nm) is chosen to measure in the experiment (see Figure 16, chapter 3). Total of 96 data are collected from four different locations for each lens. Using Alicona's script (see appendix

1), three sets of data are collected in the first location before moving to the next location and up to a total of four different locations, returning to the first. The goal of this process is to reduce the effect of local variations of the measured surface. The variations mean any variation from an ideal plane of measuring surface. The measuring process is presented in Figure 61. The details of the parameters are shown in

Table 10. From Table 10, the parameters of contrast, brightness/exposure time, vertical and lateral resolution were chosen to assist in gaining the image data from both objectives. The experiment is applied at the normal measuring temperature and humidity. For the purpose of data analysis, the MountainsMap software program is used for data analyses. With the Mountainsmap software program, a number of measurement data can be averaged together. The levelling process was performed for the averaged surface of the 96 sets of measuring data. Threshold, by removing points that have distances more than three standard deviations from the average point heights, was processed on the levelled surface. Two filter settings of the ISO standard and the proposed method were applied on the data of threshold surface. The threshold value was material ratio 0.5% to 99.5%. The ISO filter was a low pass Gaussian filter applied as stated in the ISO standard to generate an SF-surface with a cut-off value that is equal to one-tenth of the field of view. The proposed filter method was to multiply the sample distance of the field of view of each objective by ten. The value of Sz was calculated after the filtration process. Figure 62 represents the analysis process of obtaining Sz value using Mountainsmap. From Figure 62, the averaged surface refers to the result of the 96 averaging surfaces.

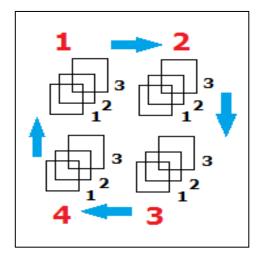


Figure 61: Measuring process

Table 10: The experimental parameters

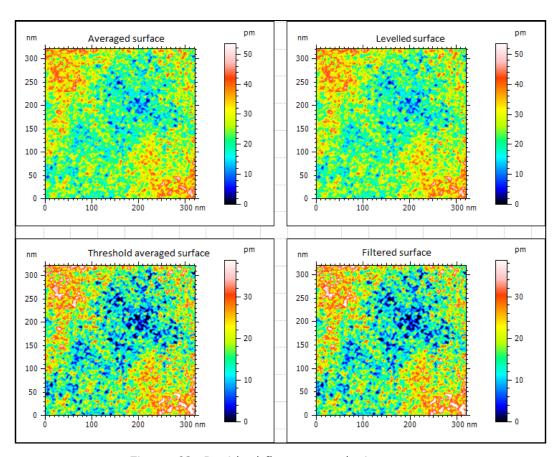


Figure 62: Residual flatness analysis process

5.2 Results

The results have been obtained by averaging from number of surfaces. The levelling process is applied on the averaged surface. To remove the spikes from the levelled surface, the threshold operation is performed. Before calculating the Sz values of the residual flatness, two different filter processes are followed, namely the ISO instructions of the filtering process and another filtering process (proposed method). A low pass Gaussian filter is applied as stated in the ISO standard to generate an SF-surface with a cut-off value that is equal to one tenth of the field of view. The cut-off of the $50\times$ objective lens was 32 μ m and for the $100\times$ was 16 μ m. The filter using other process is

selected by multiplying the sample distance of the field of view of each objective by ten. The sampling distances of the $50\times$ and $100\times$ lenses are $0.176~\mu m$ and $0.088~\mu m$, respectively; hence, the other filtering process uses a filter with sampling distances of $1.76~\mu m$ and $0.88~\mu m$. A flow chart of the process is shown in Figure 63. The Sz values of the filter process following the ISO standard (setting 1) are 22.9~n m and 26.1~n m for $50\times$ and $100\times$ objective lenses, respectively. The Sz results of the filter procedure following the other process (setting 2) are 37.8~n m and 38.7~n m for $50\times$ and $100\times$ objective lenses, respectively. The Sz values of unfiltered data are 53.6~n m and 42.3~n m for $50\times$ and $100\times$ objective lenses, respectively. Although the difference between the two objectives is not significant, using different filter processes is statistically significant different for the residual flatness results. Figure 64 shows the Sz findings of the residual flatness.



Figure 63: The flow chart of the analytical process

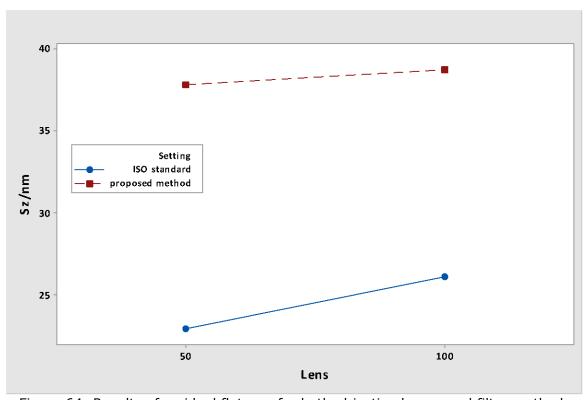


Figure 64: Results of residual flatness for both objective lenses and filter methods

5.3 Discussion

The residual flatness experiment has been conducted on the FVM instrument using two objective lenses with $50\times$ and $100\times$ magnifications. Constant parameters of contrast and brightness and vertical and lateral resolutions have been used in the experiment. A total of 96 surface data has been collected for each objective. The artefact has been measured in different locations to take into account the surface variations. The value of residual flatness has been obtained after applying a mathematically levelling process, threshold and filtering the averaged surfaces. The ISO filtering rule and the other filtering method have been applied.

The difference in values of Sz between different objectives lenses is quite small. The result of Sz is not significant when the objective lenses are changed. This finding suggests that Sz is more related to vertical scale error of the stage rather than the sensor and optical system performances. Therefore, changing the objective will not significantly affect the value of Sz. The value can be affected by scratching or/and dirt on the objectives and the measured surfaces (Leach 2011, Leach and Giusca 2012, Leach and Giusca 2013, Giusca, Claverley et al. 2014). Furthermore, the measuring method of the artefact surface has led to reduce the Sz value. Measuring the artefact surface in different locations can assist in minimising the value of Sz (vdi/vde2617 2004, Leach 2011, Leach and Giusca 2012, Leach and Giusca 2013, Giusca, Claverley et al. 2014, ISO25178:700.3 2016, ISO25178:700.3 2018). Each location on the measured surface has a different topography due to local variations of the measured surface. In addition, applying the S-filter on the surfaces in this experiment has led to reduce the effects of high spatial frequency components, which can be caused by the instrument electrical noise, for the residual flatness values. According to ISO25178:700.3 (2016) and (2018), the S-filter can assist in obtaining the effective Sz value. Using the filter can eliminate the high-frequency noise components from the surface data so that the Sz value is reduced after applying the filter process. The Sz values of unfiltered data are 53.6 nm and 42.3 nm for $50 \times$ and $100 \times$ objective lenses, respectively. Therefore, the results show that filtering process is very influential in determining the residual flatness. Subsequently, a filter value for assessing residual flatness should be carefully and appropriately selected following ISO standard to measure certain length, otherwise, the proposed method can be used instead for determining the residual flatness for FVM.

The MC of residual flatness is determined by applying either the ISO filter process or the proposed method. A suitable artefact to determine the residual flatness for FVM is a standard flat surface artefact (a Halle flat surface artefact was measured in the experiment). The experiment of residual flatness has addressed the question on what is a good practical procedure to determine the MC with suitable reference artefact.

Chapter six: Amplification, linearity and perpendicularity experiments

The thesis aims to investigate the traceability framework by determining the metrological characteristics (MCs) for a focus variation microscopy (FVM) instrument, as an optical areal surface texture measuring instrument. Therefore, this chapter investigates the determination of amplification, linearity and perpendicularity characteristics for FVM

The research aim is addressed by determining the amplification, linearity and perpendicularity characteristics of FVM by applying three novel experiments using novel and low-cost reference artefacts. The experiments are the lateral scale with multiple-image field measurements, vertical scale, and measuring the lateral scale with single image field measurement. Each experiment proposes new low-cost artefacts and procedures for vertical and lateral scale calibration. Cross grating artefacts will be measured in the lateral scale calibration experiment, with multiple image fields, with both stitching and non-stitching measuring strategies. The measurements of reference artefacts for lateral calibration of single image field and step height artefacts for vertical scale are presented.

The MC of FVM can be determined through the amplification, linearity and perpendicularity characteristics. Cross grating and step height artefacts are measured in the determination. Good practical procedures to determine the MC are followed throughout the experiments. Thus, the research aim and questions can be achieved by doing the experiments of determining the amplification, linearity and perpendicularity characteristics.

6 The experiments

6.1 Lateral scale calibration

Calibration of the material measures

In order to calibrate the distances between the centres of the calottes of the crossgrating, a Zeiss O-Inspect non-contact coordinate measuring machine (CMM) is used with a maximum permissible error specification of $E_{L,MPE} = \pm (1.6 + L/300) \, \mu \text{m}$, where L is in millimetres. This CMM is periodically performance verified to assure that it operates within its specification $E_{L,MPE}$. According to the specification, the CMM has one-magnitude higher accuracy for its x- and y-stages compared to that of the FVM, so that the distances between the centre of the calottes measured by the CMM can be used as the length reference, that is traceable via a gauge block measurement, for the distances

measured by FVM. The calottes' centre measurements are carried out in four different positions with different orientations at each position. The orientation is changed by rotating the artefact by 90° clock-wise for each position. Measurements are repeated five times for each calotte at each position. With this strategy (ISO/DTS15530-2 2007), the volumetric error of the CMM is taken into account as a contributor for the combined standard uncertainty estimation of the artefact's measurement results. Figure 65 shows the artefact calibration with the CMM, where one of the four artefact calibration positions is shown. The artefact position is not parallel to the CMM's *x*- and *y*-axes (skewed position) so that the CMM will move both the *x*- and *y*-axes to reach each calotte. By moving both axes, the errors from both axes are taken into account as influence factors in the uncertainty estimation of the calottes' centre measurements. The callotes' centre measurements are carried out by the CMM optical-head with a 2D vision system. For the traceability, the measurement of a calibrated gauge block is carried out by using the tactile sensor of the CMM.

The location of the centre of each calotte is measured and the centre distances between pairs of calottes were calculated. The centre locations are obtained by an image processing algorithm that extracts the points of the detected circle of callotes and associates a circle geometry to the extracted points to obtain the centre location of the callotes. Table 11 shows details of the uncertainty estimation for the centre distance and maximum combined uncertainty of a distance between two calottes on the artefact. In Table 11, all influence factors are detailed (The calculation process of Table 11 is in appendix 4). The factors consider the CMM repeatability, CMM geometric error, temperature variation and uncertainty for the length measurement of a Grade 1 gauge block. The measurement uncertainty of the length (the centre distance between two calottes) is estimated according to ISO/DTS 15530-2 for calibration with a CMM (ISO/DTS15530-2 2007). Traceability of the calibration results is established with a substitution measurement of the gauge block, with the tactile sensor of the CMM, with nominal length 4 mm (equal to the nominal length being calibrated).

Table 11: All influence factors of the calibration process. The calculation for the largest uncertainty among all the centre distances is shown.

Sources	Value /μm	Description	
u _{rep}	0.817	Influence factor considering the CMM repeatability, part property (form, texture), sampling strategy, contamination of the surface, etc. (Type A).	
u_{geo}	0.316	Influence factor considering CMM geometric error, stylus error, tip error, fixturing error and alignment error (Type A).	
U _{corr}	0.052	Influence factor considering the length error correction applied to the length measurement (only applied for distance/length and size measurement) (Type B).	
u _{temp}	u_{temp} 0.005Influence factor due to thermal variation and error of coefficient thermal expansion of the measured part (Type)		
U gaugeblock	Influence factor from the measurement of the calibrated gauge block (Grade 1 gauge block) (Type B).		
u total	0.88	Combined standard uncertainty	

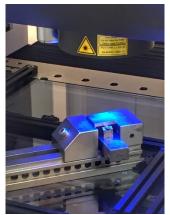


Figure 65: The artefact calibration with the CMM

The second artefact of cross grating has also been measured and calibrated using Zeiss O-inspect CMM to estimate the measurement uncertainty and achieving the traceability (see Figure 65). The measurements have been carried out in four different orientation positions. The measurements have been repeated five times for each hemisphere. The measurement uncertainty of each artefact have been estimated following (ISO/DTS15530-2 2007). Several factors are influence the measurement uncertainty of length errors considering the CMM repeatability, CMM geometric error, temperature variation and uncertainty for the length measurement of reference artefact. The maximum combined standard uncertainty of cross grating artefact is 0.71 µm. Table 12 shows the calibration process of cross grating artefact (The calculation process of Table 12 is in appendix 5.

Table 12: The calibration process of second cross grating artefact. The calculation for the largest uncertainty among all the centre distances is shown

Sources	Value / µm	Description
U _{rep}	0.404	Uncertainty source considering the CMM repeatability, part property
		(form, roughness), sampling strategy, dirt of the surface, etc.
U _{geo}	0.527	Uncertainty source considering CMM geometric error, stylus error, tip
		error, fixturing error and alignment error
U _{corr}	0.252	Uncertainty source considering the error applied to the length
		measurement (only applied for distance/length and size
		measurement)
U _{temp}	0.00095	Uncertainty source due to thermal variation and error of coefficient
		thermal expansion of the measured part
<i>U_{gaugeblock}</i>	0.05	Calibration of gauge block
U _{total}	0.71	

Experimental design

Two objective lenses of $5\times$ and $10\times$ magnifications have been chosen to measure the cross-grating artefact in x- (horizontal), y- (vertical) and diagonal directions. The image fields of the $5\times$ and $10\times$ objectives are $(2.82\times2.82)\,\mathrm{mm}$ and $(1.62\times1.62)\,\mathrm{mm}$, respectively. The objectives have been chosen to give a relatively large size of image field. The area of measurements is larger than the image field of both the objectives. The measurements are carried out at one height (z - direction) location (at the height of the instrument table where parts are placed) as the calibration is focused on the lateral performance of the FVM. Four measurement types have been determined: measurement in horizontal, vertical and diagonal directions (see Figure 66), and measurements for the whole calottes grid. Each measurement type is replicated three times and averaged to reduce random error. Both stitching and non-stitching measurement methods are applied. The measurements with stitching measure the surfaces in between two callotes and non-stitching measurements only measure the callotes' centre without measuring the surfaces in between two callotes. The purpose of stitching measurements is to study the effect of the stitching algorithm with respect to the lateral stage accuracy. The stitching measurements involve the measurement of multiple image-fields that overlap with each other and the point registration of the overlapped image-fields to reduce the error of the lateral stage. The measurements from the horizontal and vertical directions are used to calculate the perpendicularity error. For amplification and linearity in 2D, all the calottes are measured only with a stitching method, with both $5\times$ and $10\times$ objective lens magnifications, and 2D error maps are presented.

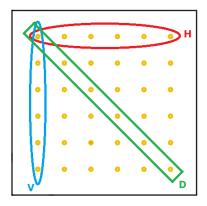


Figure 66: Horizontal (H), vertical (V) and diagonal (D) directions of the measurements.

For the measurements of the second cross grating artefact using FVM, the hemispheres that are in one image field has been measured repeatedly three times for better error estimations. The total hemispheres measurements that are covered by 5x and 10x are sixteen and four, respectively. Due to the number of the measurements using 10x are few in one image field, three different areas were measured. The data of three different measuring directions of horizontal, vertical and diagonal have been calculated for the amplification and linearity characteristics in both objective lenses. Figure 67 and Figure 68 show the covered measuring area and measurement directions for both objectives.

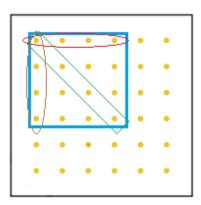


Figure 67: Measuring area using 5x

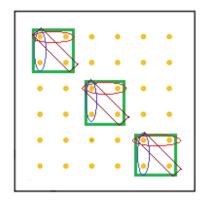


Figure 68: Measuring area using 10×

Amplification and linearity deviation results

The amplification and linearity of the xy-stage are determined by calculating the errors between two calottes' centres from measurements in the x-, y- and diagonal directions. The callote centres are calculated as the centre of a sphere associated to the 3D point cloud of the callottes. An error is defined as the difference between a calibrated length (measured by CMM) and a length measured by FVM. The length is the distance between two calottes' centres. The results show different errors for the measurements carried out in different measuring directions with both the objectives $5\times$ and $10\times$ and with and without stitching. In addition, the results show that the choice of the different objective lenses does not significantly affect the error, but the use of stitching does have a significant effect

Figure 69, Figure 70 and Figure 71 show the errors of the length measurements of $1^{\rm st}$ artefact with the $5\times$ objective lens for the horizontal, vertical and diagonal directions respectively. From Figure 69 and Figure 70, it can be seen that the average length errors measured of $1^{\rm st}$ artefact with stitching are reduced by up to 52 % and 25 % for the x- and y-directions respectively, compared to the errors obtained from the measurements without stitching. Similarly, Figure 72, Figure 73 and Figure 74 show the errors of $1^{\rm st}$ artefact for the measurements with the $10\times$ objective lens for horizontal, vertical and diagonal directions respectively. From Figure 72 and Figure 73, the average length errors can be reduced by up to 62 %, and 10 %, for x- and y-directions respectively, for measurement with stitching compared to without stitching. The length errors in the diagonal direction obtained from both the $5\times$ and $10\times$ objective lenses are similar for both stitching and non-stitching measurement strategies. The results show that the stitching algorithm is only effective for measurement in the single x- and y-directions, but is not as effective in the diagonal direction. The figure calculations are in appendix 6.

From the non-stitching measurements with both the $5\times$ and $10\times$ objective lenses, the results show that the lateral error of the stage is the largest in the x-direction. Since the non-stitching strategy measures each calotte separately to calculate their centre positions, their errors cannot be numerically compensated. Numerical compensations are applied by stitching overlapping surfaces when the calottes are measured. The measurement results obtained by the $10\times$ objective lens with the stitching method have lower errors than the measurements obtained by the $5\times$ objective lens. Lager numbers of images for stitching are obtained to reconstruct the measured surfaces with the $10\times$ objective lens due to a smaller field of view. Subsequently, with larger numbers of images for stitching, compensation of the stage's error can be improved so that the measurement error is reduced. The higher error of the non-stitching method could be because of no compensation of stage error is available.

The measurement uncertainty of length errors considers several influence factors: the standard error from measurement repetitions, the uncertainty of the length calibration, the error due to the material expansion and the error in the estimation of the coefficient of the material's thermal expansion coefficient. Table 13 shows the influence factors that contribute to the measurement uncertainty. In Table 13, the largest uncertainty estimation corresponding to a 20 mm length measurement is shown. The combined standard uncertainty for the 20 mm length measurement is $1.48\mu m$.

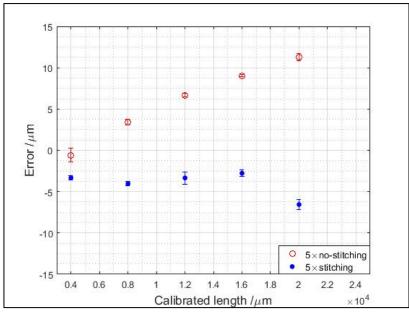


Figure 69: Results of the error calculation of 1^{st} artefact for the $5\times$ objective in the horizontal direction

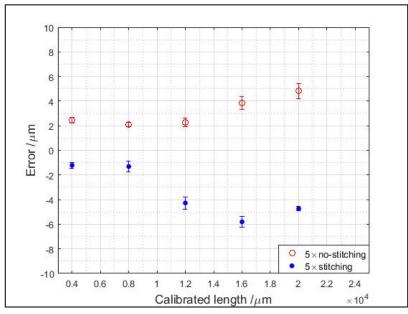


Figure 70: Results of the error calculation of $\mathbf{1}^{st}$ artefact for the $5\times$ objective in the vertical direction.

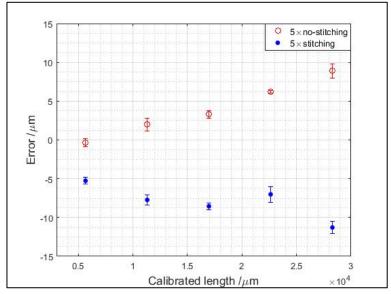


Figure 71: Results of the error calculation of 1^{st} artefact for the 5x objective in the diagonal direction.

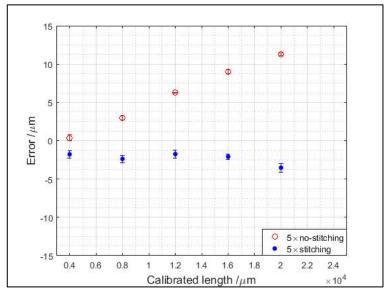


Figure 72: Results of the error calculation of $\mathbf{1}^{\text{st}}$ artefact for the 10x objective in the horizontal direction.

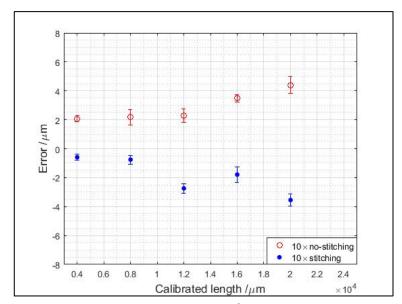


Figure 73: Results of the error calculation of $\mathbf{1}^{\text{st}}$ artefact for the 10x objective in the vertical direction.

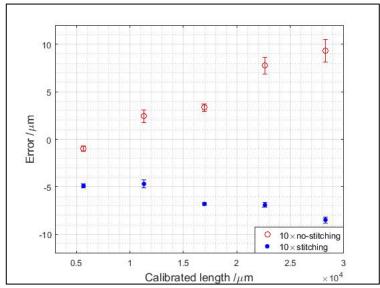


Figure 74: Results of the error calculation of 1st artefact for the 10x objective in the diagonal direction.

Table 13: Measurement uncertainty estimation and its influence factors. The shown estimated combined uncertainty is the largest uncertainty estimation among the errors measured with the $5\times$ and $10\times$ objective lenses corresponding to a 20 mm length measurement.

Uncertainty	Value /	Description
contributor	μm	
U _{rep}	1.17	Standard error from multiple measurements (Type A).
U _{temp}	0.23	Uncertainty due to stainless steel coefficient of thermal expansion (CTE) $11.7 \times 10^{-6} \text{K}^{-1}$ and $\Delta T = 1 ^{\circ}\text{C}$) (Type B).
U _{CTE}	0.023	Uncertainty due to error in the CTE estimation (10 % CTE) (Type B).
U _{trace}	0.88	Uncertainty of calibration of the length (Type B).
U total	1.48	Combined uncertainty

According to the results of an analysis of variance (ANOVA), the length measurement errors obtained with the $5\times$ and $10\times$ objectives are statistically similar for all the measurements in x-, y- and diagonal-directions. The results show that the errors are mostly contributed by the performance of the xy-stage. Therefore, changing the objective may not significantly affect the results of the calibration. Giusca, Leach et al. (2012) also reported that errors of amplification, linearity and perpendicularity of the xy-stage of other instruments are not affected by the magnification of the objectives. The results suggest that a low magnification lens can be used to determine the amplification and linearity errors of the xy-stage. By using a low magnification lens, a larger field of view can be obtained so that measurement time can be reduced.

In summary, the results of the amplification coefficient (α) and linearity deviation (I), following their definition in ISO/DIS 25178 (ISO25178:600 2018), are numerically

presented in Table 14. From Table 14, the calculated amplification coefficients show that the measurements with stitching tend to decrease the measured distance and the measurements without stitching tend to increase the measured distance between the centres of two callottes. The amplification coefficients calculated from the measurements with stitching have value less than one unity, meaning the measured distances are shorter than the calibrated distance. In contrast, the coefficients calculated from measurements without stitching have values more than unity, meaning the measured distances are longer than the calibrated distances. From the calculated linearity deviation shown in Table 14, the results show that, even though the measurements with stitching decrease the stage errors, they also increase the non-linearity. It is worth noting that the stage error and linearity deviation are different. The stage errors show the difference between a measured and calibrated distance between two callottes' centres, while linearity deviations show the maximum difference between the measured data and the line from which the amplification coefficient is derived (ISO25178:600 2018).

Table 14: The calculated values of amplification coefficient and linearity deviation.

	5×		10×	
Amplification coefficient (a)	stitching	non-stitching	stitching	non-stitching
a_{x}	0.99987	1.0007	0.99992	1.00069
a _v	0.99971	1.00016	0.99982	1.00015
$a_{ m diagonal}$	0.9998	1.0004	0.99983	1.00045
Linearity deviation (/)	stitching	non-stitching	stitching	non-stitching
I_x / μ m	1.24	0.51	0.41	0.21
l _y /μm	0.84	0.60	0.61	0.42
l _{diagonal} /μm	1.47	0.51	0.51	0.73

The error results of the second cross grating artefact of $5\times$ and $10\times$ objective lenses have been collected for horizontal, vertical and diagonal directions. For the $5\times$ objective lens, the horizontal direction has low error comparing to the other directions. The high error, that can caused by dirt, for the vertical direction may be obtained. Figure 75, Figure 76 and Figure 77 show the error results of 2^{nd} artefact with $5\times$ objective lens for horizontal, vertical and diagonal direction, respectively. Due to small area can be measured using $10\times$ objective lens, the error results for all different measuring positions in different directions are presented in Table 15, Table 16 and Table 17. Each measuring position has different results. The error results of position1 in all measuring directions are lower the other measuring positions. The vertical direction has high error result in measuring position 1. The measuring position 2 shows the horizontal direction is higher error than the other directions. In the measuring position 3, the diagonal results are higher than the horizontal and vertical directions. It is important to know that each measuring area

position has different error stage, therefore, it is difficult to obtain same error results in different measuring positions. When the measuring area is changed, a new measuring data can be collected. The figure calculations are in appendix 7.

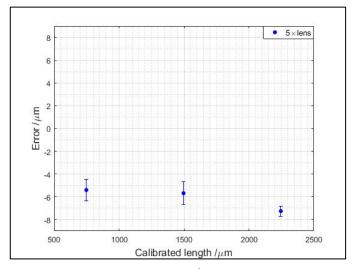


Figure 75: Results of error calculation of 2^{nd} artefact for the $5\times$ objective lens for horizontal direction

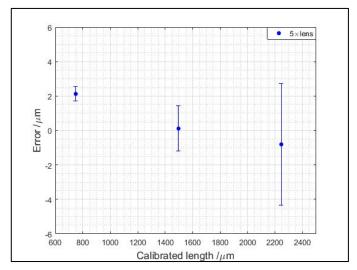


Figure 76: Results of error calculation of 2^{nd} artefact for the $5\times$ objective lens for vertical direction

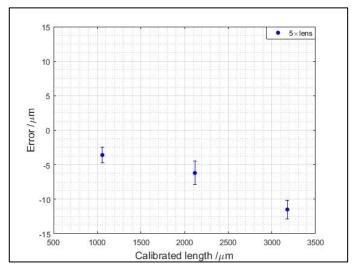


Figure 77: Results of error calculation of 2^{nd} artefact for the $5\times$ objective lens for diagonal direction

Table 15: Error results of 2^{nd} artefact for $10 \times$ objective lens for horizontal direction in different positions

TRIAL	POSITION1 /μm	POSITION2 / μm	POSITION3 /μm
1	-1.95	-1.94	-1.87
2	-2.60	-3.25	-1.98
3	-1.93	-4.03	-3.08

Table 16: Error results of 2^{nd} artefact for $10 \times$ objective lens for vertical direction in different positions

TRIAL	POSITION1 / μm	POSITION2 /μm	POSITION3 /μm
1	-0.26	-1.61	-3.07
2	0.22	-1.03	-1.34
3	-1.67	-2.27	-1.36

Table 17: Error results of 2^{nd} artefact for $10\times$ objective lens for diagonal direction in different positions

TRIAL	POSITION1 /μm	POSITION2 /μm	POSITION3 /μm
1	-2.97	-3.63	-2.75
2	-0.97	-3.32	-4.42
3	-2.61	-3.42	-4.37

Perpendicularity deviation result

The perpendicularity deviation is obtained by calculating the differences of the angles between the x- and y-axes from the CMM measured data and from the FVM measured data. For the perpendicularity deviation, the calottes' centre locations are estimated from the measurements in the x- and y-directions, using stitching and non-stitching strategies. Three repeated measurements are carried out for stitching and non-stitching measurements to estimate the calottes' centre locations. From the estimated calottes' centre locations, least-square lines are fitted to the centre locations in both the x- and ydirections. The perpendicularity deviation the $5\times$ and $10\times$ objective lenses are 0.46° and 0.22° for the measurements with stitching, and 0.22° and 0.19° for the measurements without stitching, respectively. Table 18 shows the results of all perpendicularity deviations. From Table 18, the maximum differences for the perpendicularity deviation for both stitching and non-stitching measuring strategies, and both the objective lenses are around ± 0.2°. Giusca, Leach et al. (2012) also found a similar perpendicularity deviation of $0.3\,^{\circ}$ with a coherence scanning interferometer. The differences in $5\times$ and 10× for the second cross grating artefact are 0.002° and -0.023°, respectively. Table 19 shows the perpendicularity calculation of second cross grating artefact.

Table 18: Results of perpendicularity deviation (± standard deviation of the mean).

	5× STITCHING /	5× NON- STITCHING / °	10× STITCHING /°	10× NON- STITCHING / °
FVM	90.46 ±0.53	89.77 ±0.20	90.22 ±0.07	90.19 ±0.46
СММ	89.99±0.01			
Difference	0.46	0.22	0.22	0.19

Table 19: Results of perpendicularity calculation for the second cross grating artefact

	5x / °	10x / °	
FVM	90.003 ± 0.06	89.979 ± 0.05	
СММ	90.002		
Difference	0.002	-0.023	

Amplification and linearity errors in 2D

The amplification and linearity deviation in xy-directions are presented as 2D error maps. The 2D error maps for measurements with the $5\times$ and $10\times$ objectives lenses are shown in Figure 78 and Figure 79 respectively. For all the measurements, stitching is employed and the measurements cover the whole surface of the artefact. All the calottes' centre

locations are calculated from the average of three repeated measurements. The coordinates of the calculated centres are mathematically aligned, by least-squares fitting a line to the callottes' central position, calculating the angle of the fitted line with respect to the x-axis of the reference coordinate system and rotating all the central positions based on the calculated angle, to remove errors due to fixturing and placement when setting up the artefact for the measurements. After the alignment, all centre locations from both the measurements of CMM and FVM are registered and overlapped, by translating the coordinate system of all the centre positions (from both the CMM and FVM measurements) to the centroid position of the centre location, based on their centroid locations (Daemi, Ekberg et al. 2017). After all the centre locations have been registered and overlapped, the errors of each centre's location on the grid are calculated as the difference between the centre locations measured with the FVM and centre locations measured with the CMM. The centre locations measured with the CMM are used as reference values. The maximum differences between the CMM and FVM measurements with the $5\times$ and $10\times$ objective lenses are 7.6 μ m and 5.2 μ m, respectively (The CMM data calculations of the figures are in appendix 8).

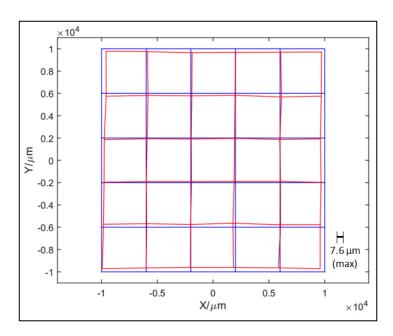


Figure 78: 2D error map for the measurement obtained with the $5 \times$ objective lens (the FVM data is red and the CMM is blue).

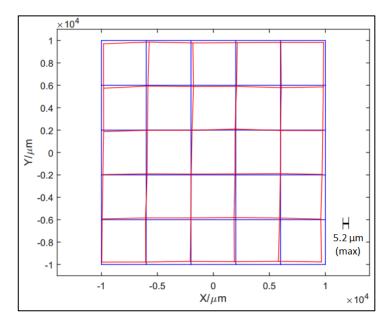


Figure 79: 2D error map for the measurement obtained with the $10 \times$ objective lens (the FVM data is red and the CMM is blue).

From the 2D error maps, it can be seen that the measurement errors with stitching, for both the $5\times$ and $10\times$ objectives lenses, are generally 15 % higher than the errors in the single axis measurements with stitching. The increase of the errors can be attributed to the contribution of both the x- and y-axis errors for the 2D measurements.

6.2 Vertical scale measurement

Prior to measuring the new artefacts using FVM, the artefacts have been measured and calibrated using Zeiss O-inspect CMM to estimate the measurement uncertainty and achieving the traceability. The measurement has been repeated five times for each slot in step height artefact. The measurement uncertainty of each artefact have been estimated following (ISO/DTS15530-2 2007). Several factors are influence the measurement uncertainty of length errors considering the CMM repeatability, CMM geometric error, temperature variation and uncertainty for the length measurement of reference artefact. The maximum combined standard uncertainty of the step height artefact is $0.22~\mu m$. Table 20 shows the calibration process of step height artefact (The calculations of Table 20 are in appendix 9). Each source in table 20 shows the maximum value obtained in appendix 9. For example, the value of u_{total} is the square root calculation of the sum of each squared source.

Table 20: The calibration process of step height artefact

Sources	Value / μm	Description
u _{rep}	0.097	Uncertainty source considering the CMM repeatability, part property
		(form, roughness), sampling strategy, dirt of the surface, etc.
.,	0.101	Uncertainty source considering CMM geometric error, stylus error, tip
u _{geo} 0		error, fixturing error and alignment error
u _{corr}	0.158	Uncertainty source considering the error applied to the length
		measurement (only applied for distance/length and size measurement)
	0.00062	Uncertainty source due to thermal variation and error of coefficient
U _{temp}	0.00062	thermal expansion of the measured part
U gaugeblock	0.05	Calibration of gauge block
u total	0.22	

The measurements of step height artefact have been carried out at five different vertical heights of 15mm, 35mm, 55mm, 75mm and 90mm. Each slot measurement in each vertical height has been repeated three times. All the measurements have been carried out using 50x objective lens with increasing the vertical resolution to detect the small error. The distance between the top point and bottom point of each slot is calculated. The calculation of step height artefact is applied using MountainsMap software. Figure80 shows the step height slot from the top.

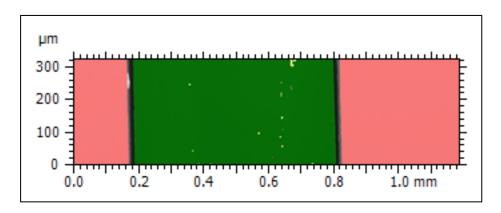


Figure 80: Top view of step height

The results of Step height artefact:

The measurement results of step height artefact are collected at different vertical height levels. The results from FVM are compared with the reference CMM results. Measuring at

different height level does not indicate any differences between the levels. As the artefact is measured using one objective lens ($50\times$), Each level can measure the artefact with the same measuring field of view of objective lens and measuring vertical distance. However, the measurement at level 15 mm can be maximum differences between the CMM and FVM. The maximum difference result is 3.14 μ m. Figure 81 shows the results of step height measurements.

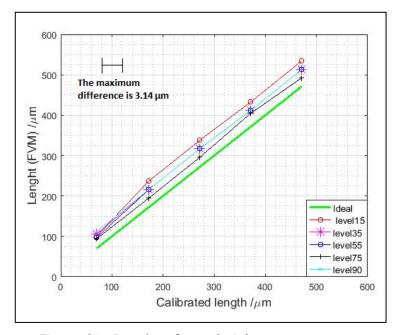


Figure 81: Results of step height measurements

6.3 Single image field calibration

Prior to measure the artefact with FVM, a coherence scanning interferometer (CSI) instrument has been used as reference in the artefact calibration (CSI instrument is traceable). Five repeated measurements in four different positions are carried out using $20 \times$ objective lens. Figure 82 presents the artefact measuring with CSI instrument. The FVM measure the artefact using $10 \times$ and $20 \times$ objective lenses. Three repeated measurements are carried out for each objective. The amplification and linearity are determined by calculating the errors between two intersection's centres from measurements in the x-, y- and diagonal directions. An error is defined as the difference between a calibrated length (measured by CSI) and a length measured by FVM.

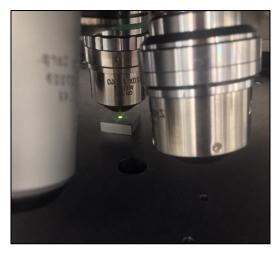


Figure 82: The artefact measurement with CSI

Measurement Uncertainty calculation:

Zygo CSI instrument was used to calibrate the distances between the intersection centres of the artefact. Zygo CSI instrument is used as the length reference due to its higher accuracy compared to the FVM. The measurement uncertainty of the length (the centre distance of between two intersections) was estimated. The artefact is measured in four different positions with different orientations at each position. The orientation is changed by rotating the artefact by 90° clock-wise for each position. Measurements were repeated five repeated measurement were carried out at each position. Several factors influence the measurement uncertainty of length errors considering the Zygo repeatability, Zygo geometric error, temperature variation and uncertainty for the length measurement of reference artefact. Table 21 shows the calibration process of the cross grating artefact. The maximum combined standard uncertainty in Table 21 is 1.7414 µm. From Table 21, it is important to notice that a calibrated reference artefact called areal cross grating is measured by a commercial coherence scanning interferometry (CSI) from Zygo to achieve the traceability. The calculations of Table 21 are in appendix 10. The result of reference artefact is contributed in the total calculation of calibration process. Due to non-deterministic features that were shown in Figure 29, large uncertainty calibration is obtained in Table 21. Each source in Table 21 presents the maximum value obtained from the calculation in appendix 10. For example, the value of $oldsymbol{u_{rep}}$ indicates its maximum value of the calculation in appendix 10, while the value of $\boldsymbol{u}_{\text{total}}$ is the square root calculation of the sum of each squared source.

Table 21: The calibration process of cross gating artefact

Source	Value / µm	Description
U _{rep}		Uncertainty source considering the Zygo repeatability, part
	1.5544	property (form, roughness), sampling strategy, dirt of the surface,
		etc.
\mathbf{u}_{geo}		Uncertainty source considering Zygo geometric error, stylus error,
	0.5605	tip error, fixturing error and alignment error
U _{corr}		Uncertainty source considering the error applied to the length
	0.00008816	measurement (only applied for distance/length and size
		measurement)
U _{temp}		Uncertainty source due to thermal variation and error of coefficient
	9.29356E-08	thermal expansion of the measured part
U reference artefact	0.55	Calibration of reference artefact
u _{total}	1.7414	Combined standard uncertainty

Amplification coefficient and linearity deviation results:

The results show different errors for the measurements carried out in different measuring directions with both the objectives $10\times$ and $20\times$. The errors of the length measurements with the $10\times$ objective lens are in Figure 83, Figure 84 and Figure 85 for the horizontal, vertical and diagonal directions, respectively. Similar results are obtained from different objective lenses. The errors of diagonal direction are higher than the errors of other directions in both objectives. The instrument algorithm can be more effective when measuring in vertical and horizontal directions. Figure 86, Figure 87 and Figure 88 show the errors of length measurements with the $20\times$ objective lens for the horizontal, vertical and diagonal directions, respectively (The figure calculations are in appendix 11).

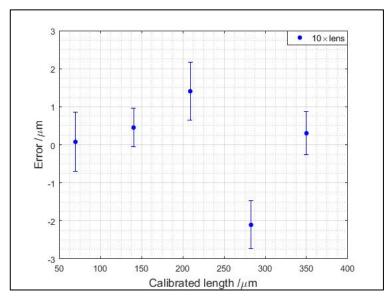


Figure 83: Error results of $10\times$ in horizontal direction

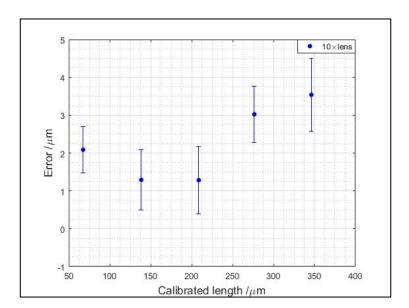


Figure 84: Error results of $10\times$ in vertical direction

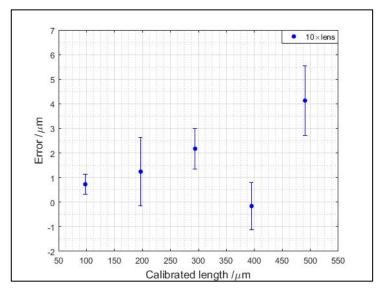


Figure 85: Error results of $10 \times$ in diagonal direction

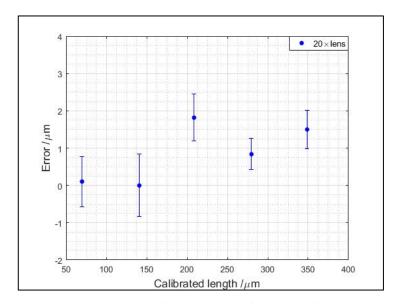


Figure 86: Error results of 20× in horizontal direction

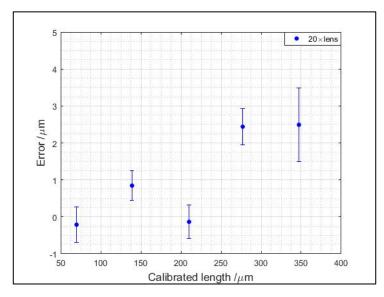


Figure 87: Error results of $20\times$ in vertical direction

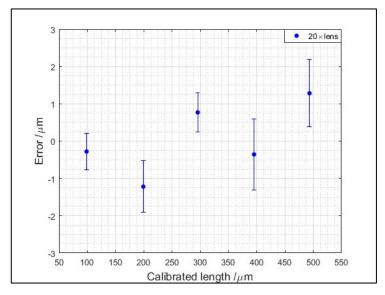


Figure 88: Error results of 20× in diagonal direction

Perpendicularity deviation results:

The perpendicularity deviation is obtained by calculating the differences of the angles between the x- and y-axes from the CSI and FVM measured data. The perpendicularity deviation estimates the measurement of the intersection's centre locations in the x- and y-directions. Three repeated measurements are carried out for the intersection's centre locations in both objectives. A least-square lines are fitted to the centre locations in both the x- and y- directions. The perpendicularity deviation of the $10\times$ and $20\times$ objective lenses are 0.155° and 0.391° , respectively. Table 22 shows the results of all perpendicularity deviations. The maximum differences in Table 22 for the perpendicularity deviation for both the objective lenses are around \pm 0.2°.

Table 22: The perpendicularity calculation

Amplification and linearity errors in 2D:

The measurements are applied on the whole artefact surface. The average of three repeated measurements of all the centre intersection locations are calculated. The intersection centres are mathematically aligned by fitting the least-squares line. Then, the angle of the fitted line is calculated with the reference coordinate system. All the central positions are rotated to remove errors based on the calculated angle. The registered centre location from Zygo and FVM are overlapped to the centroid position of the centre location. The error differences of each centre's location between Zygo and FVM are calculated. The centre locations of Zygo value is used as reference. The maximum differences between the Zygo and FVM measurements with the $10\times$ and $20\times$ objective lenses are 3.3 μ m and 2.8 μ m, respectively. Figure 89 and Figure 90 show the 2D map of error map for the $10\times$ and $20\times$ objective lenses, respectively. (The data calculation of the figures is in appendix 12).

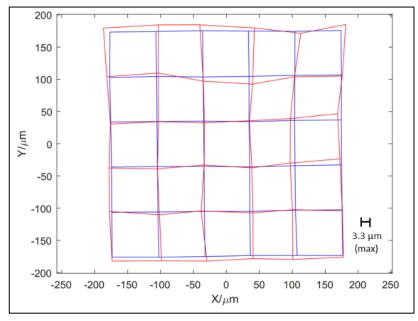


Figure 89: 2D error map for the measurement obtained with the $10 \times$ objective lens (the FVM data is red and the Zygo is blue)

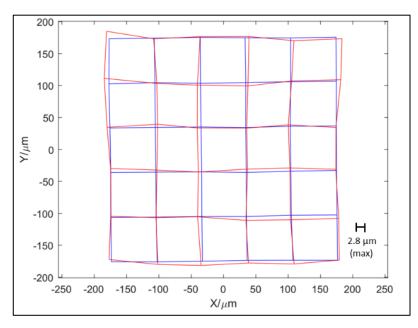


Figure 90: 2D error map for the measurement obtained with the20× objective lens (the FVM data is red and the Zygo is blue)

Conclusion and future work

The calibration of the vertical and lateral scale for FVM is presented by determining its amplification, linearity and perpendicularity characteristics. For lateral scale calibration measurement, a novel and low-cost calibrated cross-grating artefact (£100 for manufacturing cost), consisting of a grid of calottes, and procedures for the determination of linearity, amplification and perpendicularity characteristics have been proposed. As part of this study for determining the characteristics, two objective lenses of $5\times$ and $10\times$ are used to measure the proposed cross-grating artefact with both stitching and non-stitching strategies. Measurements in the horizontal, vertical and diagonal directions, along with measurements of the entire grid of calottes, are carried out. The results from the measurements of the proposed cross-grating artefact indicate that:

- 1. Measurements with stitching can reduce errors in the x- and y-directions, but not in the diagonal direction.
- 2. Measurements in 2D direction have 15 % larger errors than measurements in only one direction.
- 3. Measurements with stitching can significantly reduce lateral stage error, but increase the non-linearity of the error.

For the measurement results of the second cross grating artefact, a high error has been found in the vertical direction of $5 \times$ objective lens. Some dust on the measured artefact

may be the reason behind the obtained high error. Regarding the measurement using $10\times$ objective lens, different measuring positions are carried out due to small measuring area can be covered. Each measuring position has different measuring error results. Small measuring dimensions should be used to collect a good measuring process for single image field.

In the calibration of single image field experiment, some issues have limited determining the amplification coefficient, linearity deviation and perpendicularly characteristic. The micro features of used artefact have non-deterministic square shapes due to the manufacturing process complexity. In the process, some of the slot intersections of the artefact have inaccurate dimensions due to tool wear during cutting. This issue causes a high uncertainty when calibrating the artefact and make it not reliable. A large uncertainty of artefact calibration reduces the significance of the experiment data. Some post processing for the artefact may be required to get a better shape and to avoid this issue. When the artefact is measured, some good features can be used for single image field, particularly, on the top right corner region (see Figure 29). Alternatively, another type of micro-scale precision machining can be used to get deterministic grid shape with a possibility of more complex processing and higher manufacturing cost. The high manufacturing technology, for example special nano-pulse laser drilling may produce required artefact with precise dimensions. However, it is important considering the cost of making a new artefact using high manufacturing technology such as laser texturing process. The new artefact can be designed and manufactured using high manufacturing technology in the future work.

The MC of amplification, linearity and perpendicularity have been determined in the experiments for lateral and vertical scale measurements. The measurement of lateral scale was applied for single and multiple image fields using low-cost manufactured artefacts of cross grating and the measurement of vertical scale is performed using step height artefact. The process of applying the experiment addressed the question of good practical procedures to determine the MC with the suitable reference artefact.

Chapter seven: Topographic spatial resolution experiment

The thesis aims to investigate the traceability framework by determining the metrological characteristics (MCs) for a focus variation microscopy (FVM) instrument, as an optical areal surface texture measuring instrument. Therefore, this chapter investigates the lateral period limit (LPL) determination for FVM.

The research aim is addressed by determining the LPL of FVM by comparing its resolution with CSI measuring instruments using 20x with FVM and 20x and 50x objective lenses with CSI. The traceability will be achieved by linking the FVM results with CSI results. The CSI instrument is used to measure a calibrated reference start artefact to calibrate the LPL of the CSI. The MC of FVM can be determined through the LPL. Random surface artefact is measured in the determination of LPL for FVM. Good practical procedures to determine the MC are followed throughout the experiment. The resolution of CSI measuring instrument can be predicted as better than the resolution of FVM. The research aims and questions can be achieved by doing the experiment of determining the LPL.

7.1 A methodology to determine LPL from a random surface

This methodology determines the LPL of any kind of surface, using FVM. The methodology involves the comparison of an areal measurement with another optical method that is traceable, for example CSI and confocal microscopy. Applying this methodology will be presented in the next sections. The methodology is as follows:

- 1. Measure any random surface with an FVM, at a predefined area with a specific field of view.
- 2. Measure again the predefined area with any other optical areal topography instrument, with a specific field of view that is traceable, for example, CSI or confocal microscopy. In this thesis, a CSI was used. Mathematically align the measured areal from the FVM to the measured areal from the other traceable optical instrument. This process can be applied using specific software called MountainsMap. The software includes colocalisation module that can colocalise images of different measuring instruments and overlay the images on 3D surface topography. The colocalisation is an automatic tool using advanced algorithms of pattern recognition. This algorithm of pattern recognition can detect sorts of basic features to identify matching landmarks on the two image-like datasets. The image overlaying can facilitate the correlation study between the image and topographic features. The overlays can provide 3D

visualisation, such as zooms, translation, axes rotation and adjusting the transparency of overlaid image (Digitalsurf, 2018).

- 3. Obtain areal measurements from the FVM and the other instrument with the same lateral size (measured data with the same length and width).
- 4. For each instrument, calculate the average height h_i of each lateral sampling distance d_i :

$$h_i(d_i) = \frac{1}{N} |z_{i1} - z_{i2}| \tag{8}$$

Where z_{i1} , z_{i2} are the heights at pixel location 1 and 2, with lateral distance d_i . N is the total number of height differences for each lateral distance d_i .

5. For each calculated h_i from both measured areas, each with the same d_i , calculate the transmitted height ht_i and build a transmission height curve:

$$ht_i = \left| \frac{h_i FVM - h_i CSI}{h_i CSI} \right| \times 100 \tag{9}$$

Where h_iFVM is the h_i from the FVM and h_iCSI is h_i from the CSI.

6. Determine the lateral resolution by determining the resolution that corresponds to 50 % height transmission on the transmission curve following the LPL definition (see Figure 95 and 97).

7.2 The experiment

Measurements are performed for all six grooves. Five measurements are performed on each groove. The Zygo CSI is used as a measuring reference to compare results with the FVM. A 20x objective lens is used in the FVM, and 20x and 50x objectives lenses are used in the CSI. The CSI resolution, under 20x and 50x objectives lenses, is checked by measuring a calibrated Siemens star artefact, before comparing the data with the FVM resolution, to establish traceability. Then, resolution of the CSI is determined using 20x and 50x objective lenses, according to Giusca and Leach (2013). The results from these CSI measurements are compared to the resolution results from the FVM (using the 20x objective lens). Using Mountainmap software, data are overlapped to assess the same measurement areas from both instruments. Figure 91 and Figure 92 show the surface measuring areas of the FVM and CSI instruments, using the 20x and 50x objective lenses, respectively. From these figures, the surface height coloured map measurement for the 20x objective lens of the FVM and CSI is $(600 \times 500) \, \mu m$ and $(170 \times 170) \, \mu m$ for the 50x objective lens of the CSI. This work proposes the use of a random surface artefact to determine the LPL of FVM.

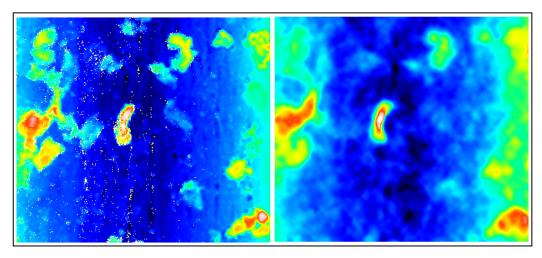


Figure 91: The measuring areas of the 20x objective lens of the Zygo CSI (left) and the 20x objective lens of the FVM (right).

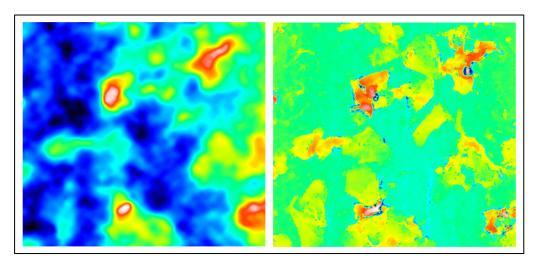


Figure 92: The measuring area of the 20x objective lens of the FVM (left) and the 50x objective lens of the Zygo CSI (right).

7.2.1 CSI 20× and 50× LPL calibration with NPL Siemens star reference artefact

The LPL is function can be used to quantify the topographic spatial resolution characteristic (ISO25178, 2018). The quantification can be performed depending on the measurement method used. The determination of LPL following the ISO definition (described in the literature review chapter) has mentioned the sinusoidal profile of ASP artefact that can be used. According to Giusca and Leach (2013), the star patterns artefact, which is often assessed using circular profiles of different diameters (see figure 93), has similar functionality compare to the use of grids. The circular profile is only limited to a discrete series of spatial frequencies. However, the advantage of the ASP

artefact can be obtained by extracting the profile of star patterns along the star radial direction. The ASP artefact that is used to determine the LPL is Siemens star artefact.

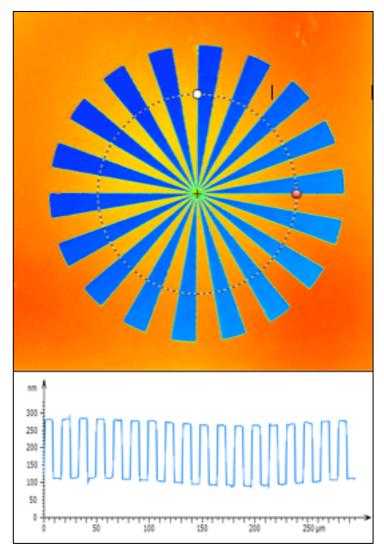


Figure 93: circular profile of ASP artefact

Prior to achieving an unbroken chain of measurement traceability, a Siemens star artefact is measured using 20x and 50x objective lenses on a CSI Zygo. The Siemens star is an NPL reference calibrated artefact, widely used for topographic spatial resolution measurement for optical measuring instruments, such as phase shifting interferometry and CSI. Figure 93 shows the Siemens star artefact used in this experiment.

The Siemens star artefact is calibrated by subtracting two profiles that are extracted through the middle of the petals. One profile is from the upper petal, while the other profile is from the lower petal. Figure 94 shows the two profiles extracted through the petals. The profiles are extracted through the middel of petals 5-23 (lower) and petals 8-26 (upper). The result of subtracting two profiles is called instrument response profile (IRP), which can determine the instrument resolution. The resolution of the instrument is determined following the ISO definition of LPL. From the IRP, the lateral scale should be multiplied by π/n (where n = petal number, 18) and the vertical scale is normalised to the maximum height (Giusca and Leach, 2013). The LPL results can be the point at which the height response of the instrument falls to 50 %. This process is applied in the determination of the LPL following the ISO 25178-6 definition. The LPL of the 20x and 50x objectives lens is (1.34 \pm 0.128) μ m and (0.783 \pm 0.064) μ m, respectively. Figure 94, Figure 95 and Figure show the process used to determine the LPL of the Siemens star artefact using CSI for 20x objective lens and Figure 97, Figure 98 and Figure 99 show the 50x objective lens results. From Figure 94 and Figure 97, two profiles are extracted through the middle of the petals; one from the lower petal and the other from the upper petal. These petal profiles are subtracted and are shown in Figure 95 and Figure 98. In Figure 96 and Figure 99, the vertical scale is normalised to the maximum height, and the lateral scale is multiplied by $\pi/18$. The LPL is determined at which the height response of the instrument falls to 50 %. These procedures are applied according to Giusca and Leach, 2013. Theoretically, the instrument resolution (optical resolution) of the 20x and 50x objective lenses is calculated using the Rayleigh criterion. The optical resolution of the 20x and 50x objective lenses of the Zygo CSI are 762.5 nm and 554.54 nm, respectively, based on the Rayleigh criterion. As the optical resolution is smaller than the LPL, the surface topography is measured. The Rayleigh criterion is used to calculate the optical resolution as follows (Leach and Haitjema 2010):

$$r=0.61\frac{\lambda}{NA}, \qquad (10)$$

where λ is the central wavelength (500 nm) of the white light, and NA is the numerical aparture of lenses. The NA of the 20x and 50x CSI objectives lens is 0.40 and 0.55, respectively.

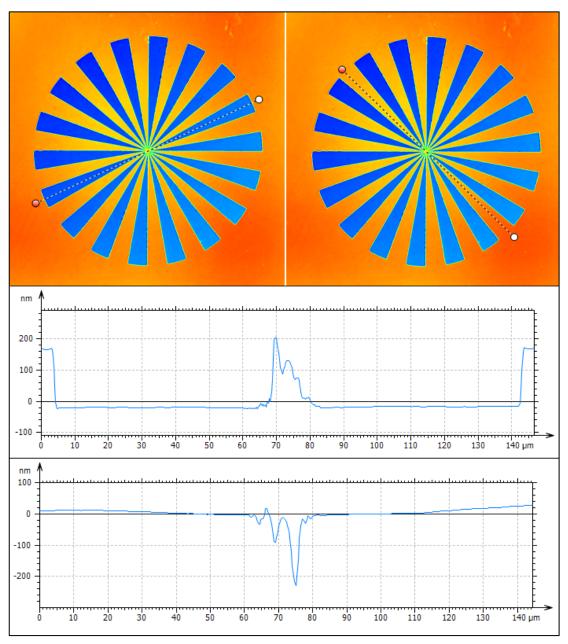


Figure 94: Two profiles extracted through the middle of the lower petal (left) and the upper petal (right) using the 20x CSI objective lens.

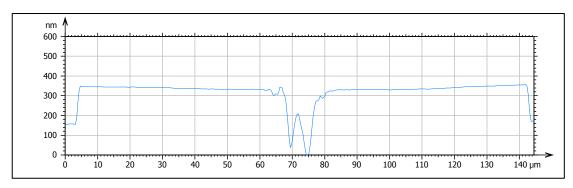


Figure 95: The subtraction result of the two profiles

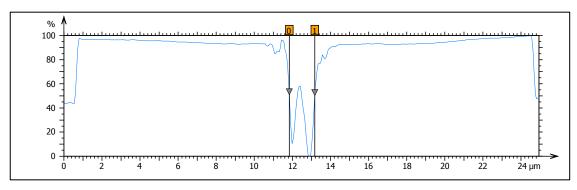


Figure 96: The lateral period limit (LPL) using the 20x CSI objective lens

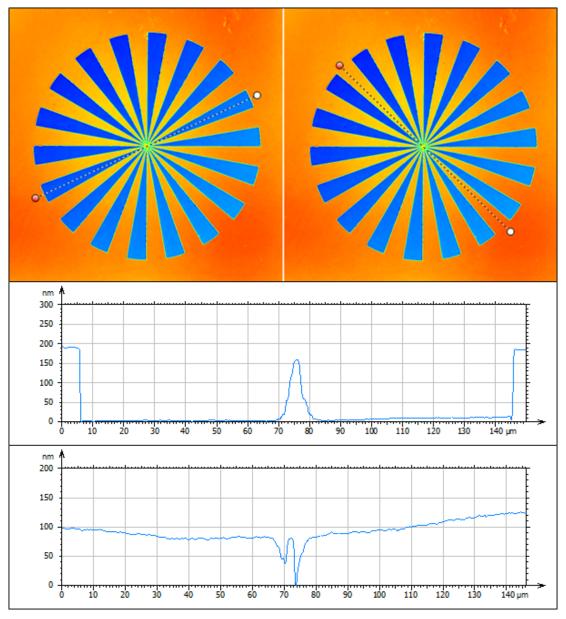


Figure 97: Two profiles extracted through the middle of the lower petal (left) and the upper petal (right) using the 50x CSI objective lens.

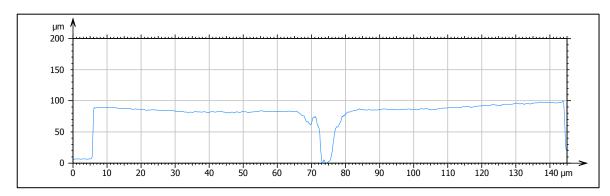


Figure 98: The subtraction result of the two profiles

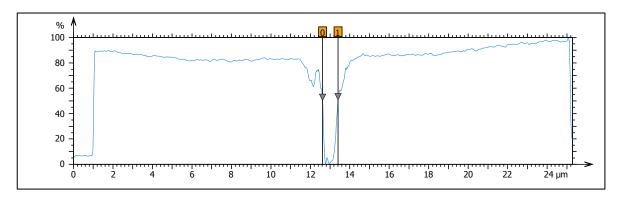


Figure 99: The lateral period limit (LPL) using the 50x CSI objective lens

7.2.2 Results

Part 1: The LPL by comparing with Zygo 20x measurement data

The experiment results of LPL compare the Zygo CSI with FVM of approximately the same measuring area. Using a 20x objective lens, different height measurement results are obtained between the 20x objective lenses of the FVM and CSI, and the 20x objective lens of the FVM with the 50x objective lens of the CSI using random surface artefact. The FVM has lower height than CSI measurements, suggesting that more filtering effects are obtained from FVM measurements. In addition, the more filtering effects suggest that FVM has lower lateral resolution when compared to the CSI instrument. The filter process can remove the effect of high spatial frequency noise. Figure 100 shows profile data comparisons between CSI and FVM. The LPL is calculated using height transmission, by determining the corresponding lateral resolution that corresponds to a 50 % height transmission. The LPL using height transmission is presented in Figure 101. From the fitted curve in Figure 101, 50 % transmission height corresponds to 19 μ m, therefore, the estimated LPL for the FVM is determined at 19 μ m, and the LPL of the 20x CSI objective lens is 1.34 μ m. The optical resolution of the 20x CSI objective lens is 0.7762 μ m.

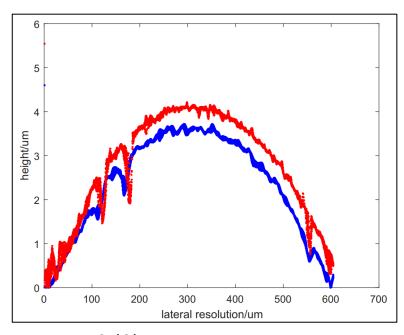


Figure 100: Average height $h_i(d_i)$ data comparisons (blue) FVM 20imes and (red) CSI 20imes

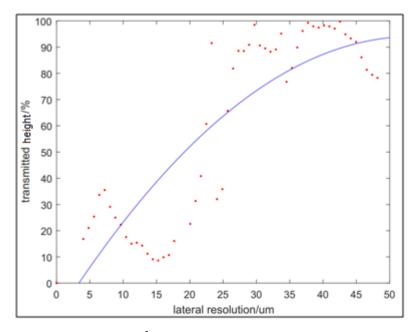


Figure 101: Height transmission ht_i data (red dots) between FVM 20× and CSI 20x lenses. Fitting curve (blue line). The lateral resolution corresponding to the 50 % height transmission is 19 μ m and the calculated optical resolution is 0.7762 μ m.

Part 2: LPL by comparing with Zygo 50x measurement data

Another experiment compared the same measuring area of Zygo CSI using a 50x objective lens with FVM using a 20x objective lens. In this experiment, the LPL is

determined by comparing different objective lenses. Due to different objective sizes between the two instruments, the results of same measuring area seem not appropriate. The graph should present similar results for the same measuring area. Figure 102 compares the profile of the 20x FVM objective lens (blue) with the 50x CSI objective lens (red). Calculation of LPL, using height transmission, is presented in Figure 103. From this figure, 50 % transmission height from the fitted curve corresponds to 4.8 μ m, therefore the estimated LPL of the FVM is 4.8 μ m and the LPL of the 50x CSI objective lens is 0.783 μ m. The optical resolution of the 50x CSI objective lens is 0.554 μ m.

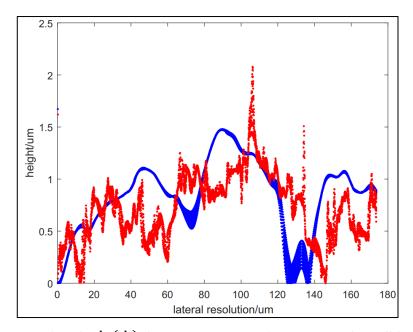


Figure 102: Average height $h_i(d_i)$ data comparisons for FVM 20x lens (blue) and the CSI 50x lens (red).

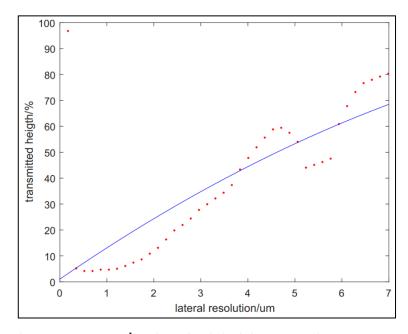


Figure 103: Height transmission ht_i data (red dot) between the FVM 20× and CSI 50x lenses. Fitting curve (blue line). The lateral resolution that corresponded to 50 % of the height transmission is 4.8 μ m, and the calculated optical resolution is 0.554 μ m.

7.3 Summary

In this experiment, a novel method to determine the LPL of an FVM instrument by measuring a rough random surface has been presented. The FVM is compared with a CSI to generate measurement traceability. Therefore, the reference artefact of the Siemens star is measured with CSI to link the traceability chain. The CSI measured the Siemens star artefact using $20\times$ and $50\times$ objective lenses. Then, the rough random surface artefact is used to compare the measurement results of the FVM and CSI. The results of the $20\times$ objective lens of the FVM are compared with the $20\times$ and $50\times$ objective lenses of the CSI.

The results showe that the CSI resolution, for both 20x and 50x objective lenses, is better than the resolution of the FVM 20x objective lens. The estimated LPL for measurements with the 20x FVM objective lens and the 20x CSI objective lens is 19 μ m and 1.34 μ m, respectively. The optical resolution of the 20x CSI objective lens is 0.7762 μ m. Comparison of the 20x FVM objective lens and the 50x CSI objective lens show that the estimated LPL of the FVM and CSI are 4.8 μ m and 0.783 μ m, respectively. The optical resolution of the 50x CSI objective lens is 0.554 μ m.

Further investigations should be carried out to confirm the efficiency of this novel method. These investigations could incorporate experiments using several random artefacts that could corroborate data from this study. The metrological characteristic of

LPL for FVM is determined using a novel method with measuring random surface artefact. The calibration procedure is presented by comparing the resolution of CSI and FVM. The traceability is achieved by measuring a reference Siemens star artefact.

Chapter eight: Conclusion and future work

8 Conclusion and future work

8.1 Conclusion

This project presents novel calibration infrastructures of FVM for surface texture measurements in the form of novel low-cost artefacts (£100 for each artefact) and practical calibration procedures to determine its MCs. The metrological characteristics of FVM, addressed in this project, include: measurement noise, residual flatness, amplification coefficients, linearity deviations and perpendicularity and topographic spatial resolution. Each MC for FVM was determined separately by measuring a suitable artefact in a separate experiment. Most of the available artefacts cannot be measured with FVM because of its limitation in measuring smooth and transparent surfaces. The new low-cost artefacts were designed and manufactured when the suitable artefact for FVM was not available; for example, the artefacts measured for determining the amplification, linearity and perpendicularity characteristics. The new artefacts were calibrated with more traceable measuring instruments to achieve the traceability. The results of the new artefacts with the more traceable instrument were compared with the FVM and the uncertainty was estimated. Each chapter is summarised as follows:

Chapter Two is a literature review of related work and covers all topics related to surface texture measurements, including application of surface texture measurements, measurement traceability, calibration, measurement uncertainty, material measures and metrological characteristics. In addition, the chapter reviews the FVM as an optical measuring instrument including its working principles, instrument components and limitations. The literature review indicates that most available reference artefacts for calibration of surface texture measuring instrument are not suitable for use with the FVM due to their very smooth surfaces. Hence, from this literature review, new reference artefacts, and the procedure to use them for calibration, are still required and are proposed in this thesis to overcome the lack of artefacts suitable for most of FVM instruments and practical procedures using the proposed artefacts to quantify the metrological characteristic.

Chapter Three: the measurement artefacts used in the determination of metrological characteristics for FVM has been presented. The artefacts for determining the measurement noise characteristic are replica of optical flat surface and flat surface artefacts. For the residual flatness determination, the artefact of Halle flat surface is used in the measurement. Three new artefacts have been designed and manufactured for the determination of amplification, linearity and perpendicularity characteristics. The

artefacts have been manufactured by Kern micro milling machine. The determination of topographic spatial resolution uses random surface artefact that is manufactured by EJM.

Chapter Four presents a work on the determination of the metrological characteristic of measurement noise, determined with both subtraction and averaging methods, for FVM. The chapter presents novel various experiments for the measurement of noise and measurement repeatability. These experiments include the determination measurement noise using replicas of an optical flat having very smooth surface with Ra < 10 nm and the determination of measurement noise with different measurement parameters, that are illumination parameters, contrast and brightness parameters. A novel experiment finding uncovers vertical scale non-linearity of the FVM by measuring its measurement noise at different scale location of the vertical motion stage. Another novel experiment is also carried out by using the replica of an optical flat to determine the measurement noise for different objective lenses at different vertical heights. The general results show that the noise determined by measuring the replica is significantly higher than the noise from the other experiments using flat surface artefacts. Instead, the replica measurements can overcome FVM limitations, but may always give higher measurement noise from a real situation. The reason could be due to the fact that the replica may have issues in the replication of surface features, therefore, measurements can be obtained from the replica, but they could affect result reliability. For this reason, the measurement of the replica of the optical flat artefact will give higher measurement noise than the measurement of the optical flat itself. The experiment using different illumination parameters shows statistically a significant effect of illumination on noise. The results also shows that measurements using polariser for determining the noise, with the same contrast setting of normal light, leads to higher noise than the measurements without using the polariser. The contrast and brightness effects on measurement noise are also carried out. Form this experiment, the noise findings indicate that changing the contrast and brightness together significantly affects the noise. The last measurement noise experiment detected the non-linearity of the vertical height for the FVM. The non-linearity of vertical scale of FVM could be caused by the way the drive train is guided, and how the Z-axis is mounted on the guiding rails. The measurement results of measurement noise determination can be achieved by using the replica of an optical flat that cannot be measured directly with the FVM due to very smooth surfaces (Ra<10nm). However, by using the replica of an optical flat artefact, high noise results are obtained. This result show that the use of replica will give an overestimate of the true measurement noise of the FVM and users should carefully aware of this result. Another measurement noise result is related to the non-linearity of vertical scale for FVM. This result is the most significant as with the measurement noise quantification; the stage non-linearity behaviour of the FVM can be detected. In this experiment, the MC can be determined through the measurement noise and measurement repeatability. The replica of an optical flat and Halle flat surface artefact were measured in the determination of measurement noise for FVM. The good practical procedure to determine the MC is described in the experimental methodology. The research aims and questions are achieved by doing these experiments to determine the measurement noise.

Chapter Five focuses on determining residual flatness characteristics. The experiment compares the determination of residual flatness by using ISO filtering rule and the proposed filtering method with two objective lenses of 50x and 100x. The proposed filtering method is applied by multiplying the sample distance of the field of view of each objective by ten. For example, the sampling distances of the 50× and 100× lenses are 0.176 µm and 0.088 µm, respectively; hence, the other filtering process uses a filter with values of 1.76 µm and 0.88 µm, respectively. The results from the ISO filtering rule are lower than the proposed filtering method for both objective lenses. The results from the ISO filtering rule are 22.9 nm and 26.1 nm for the 50× and 100× objective lenses, respectively and the results from the proposed filtering methods are 37.8 nm and 38.7 nm for the 50× and 100× objective lenses, respectively. The results show that filtering has a significant effect in determining the residual flatness and has to be chosen appropriately. The measurement results of residual flatness determination are reliable. The proposed filter method can be suggested to be applied by FVM users when the ISO filter cannot be performed. The experiment of residual flatness addressed all the three research questions. The MC of FVM was determined through the residual flatness. The Halle flat surface artefact was measured in the determination of residual flatness for FVM. Good practical procedure to determine the MC was followed throughout the experiment. The research aims and questions have been addressed by doing the experiment to determine the residual flatness.

Chapter Six: the amplification coefficient, linearity deviation and perpendicularity characteristics are determined in three novel experiments, using novel and low-cost reference artefact to determine the amplification coefficient, linearity deviation and perpendicularity characteristics for the lateral scale with multiple-image field measurements; vertical scale; and measuring the lateral scale with single image field measurement. Three new low-cost artefacts (£100 for each) were proposed to determine characteristics in vertical and lateral scale calibration. The lateral scale calibration experiment, with multiple image fields, with both stitching and non-stitching measuring strategies, used cross-grating artefacts. The results show that measurements with

stitching reduced lateral errors in the x- and y-directions (due to the inaccuracy of the lateral motion stage), but increase the stage's non-linearity of the error. This significant measurement result of the experiment is reliable. The lateral error was reduced by up to 2 µm for measurements with stitching. The proposed reference artefact for lateral calibration of single image field measurements shows a significant optical lateral error (distortion). From this result, it is recommended that some post-processing, e.g. distortion correction for the artefact may be required to get required accuracy for very smooth surfaces. Alternatively, another type of micro-scale precision machining may be used to manufacture an artefact with deterministic grid shapes, with the possibility of more complex processing and higher manufacturing costs. This process of making the artefact for single image field measurements can be a challenge and will be one of future work. The experiment of the amplification, linearity and perpendicularity characteristics addressed all the three research questions. The MC of FVM is determined through the amplification, linearity and perpendicularity characteristics. Cross grating and step height artefacts were measured in the determination. Good practical procedures to determine the MC have been proposed and implemented throughout the experiments. The research aim and questions have been answered by doing the experiments to determine the amplification, linearity and perpendicularity characteristics.

Chapter Seven: the determination of lateral period limit (LPL) is demonstrated and a novel method to determine LPL is presented. The novel method presents the use of an artefact with random surface to determine the FVM's LPL. Promising results from a methodology to determine LPL from any random surfaces are presented. The experiments compare the measuring results of FVM with CSI. The reliable results show that the resolution of CSI is better than the resolution of FVM. Traceability is achieved by measuring a calibrated artefact by the CSI and then comparing the results of the CSI with the results of the FVM. More investigation is required for the proposed method to determine the LPL using any random surface artefact. The experiment of LPL addressed all the three research questions. The MC of FVM is determined through the LPL. Random surface artefact is measured in the determination of LPL for FVM. Good practical procedures to determine the MC have been followed throughout the experiment.

In summary, the project presents novel calibration infrastructure for FVM by determining the MCs for the FVM, including: measurement noise, residual flatness and amplification coefficient, linearity deviation and perpendicularity characteristics. In general, the proposed practical procedures of calibration are developed for ease of use by the industry. The traceability is established by measuring the novel low-cost material measures by other instruments that have traceable measurement results.

8.2 Future work

The calibration infrastructure for FVM, by providing low-cost material measures (£100 for each) and practical procedures to determining metrological characteristics, was performed in this project. However, further work is required to better manufacture a reference artefact to determine the amplification coefficient, linearity deviation and perpendicularity characteristics for single image field measurements. In addition, the proposed method to determine the lateral period limit with any artefact having random surface requires more investigations, for example by validating the method with more artefact with different surface topography. The list of metrological characteristics, for surface texture measurements, as mentioned in (ISO25178:600 2018), contain topography fidelity characteristics. This project has not determined the topography fidelity for FVM, but this is planned for future work.

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References

Appendices

Appendix 1

ALICONA script for measurement noise and residual flatness (Ch. 4 and Ch. 5):

```
1 IF-AUTOMATION 1.0
2 IFMVERSION 6.1.1.1
3 END-IF-AUTOMATION
4 function iterativeCapture(){
5 var folderName="Anas";
6 var projectName="residual flatness 100x";
7 //var objectName="sample 20X ";
8 var path="D:\\Anas\\residual flatness 100x\\";
9 var fileName;
10 //====Variables declaration and assignment===========
11 var model=new SurfaceModel;
12 var factor=2;
13 var vector = new Point3DVector;
14 verResolution=0.01e-6;
15 latResolution=1.46e-6;
16 var i;
17 var n; //total number of measurement
18 var repeatition; // total number of repetition per position
19 var delta x;//movement in X direction
20 var delta_y;//movement in Y direction
21 var no_of_row; //total number of row 22 var no_of_col; //total number of column
23 var counter_row;
24 var counter_column;
25 var current_position= new Point3D;
26 var new position= new Point3D;
27 var original position= new Point3D;
28 g measureDevice.getPos(current position);
29 // this is to get start position of the measurement.
30 //initial valu for new position
31 new position.x=current_position.x;
32 new_position.y=current_position.y;
33 new position.z=current position.z;
34 original_position.x=current_position.x;
35 original_position.y=current_position.y;
36 original position.z=current position.z;
37 zUpper=original_position.z+0.5e-6;
38 zLower=original position.z-0.5e-6;
39 no of row=2;
40 no of col=2;
41 repeatition = 2; //number of repetition in each position = repetition
42 delta x=2000e-6;
43 delta_y=2000e-6;
44 var accuracyMicrometers = 0.01;
45 var accuracy = new Point3D;
46 accuracy.x = accuracyMicrometers * 1.0E-6;
47 accuracy.y = accuracyMicrometers * 1.0E-6;
48 accuracy.z = accuracyMicrometers * 1.0E-6;
49 n= no of row* no of col* repeatition; //total number of measurement
50 counter row=1;
51 counter col=1;
52 counter=0;
53 for (i=1; i \le n; i++) {
54 var model=new SurfaceModel;
56 var objectName="100X ";
```

```
57 objectName=objectName+i;
58 //Here is the code to take measurement repetition and move to other
59 area in X-Y plane
60 if((i%repeatition) == 0) {
61 if (counter row==no of row+1) {
62 counter row=1;
63 current position.x=original position.x;
65 if(counter col==no of col+1){
66 counter col=1;
67 }
68 new position.x=current position.x+delta x*counter row;
69 counter row=counter row+1;
70 new position.y=current position.y+delta y*counter col;
71 counter col= counter col+1;
72 g measureDevice.movePos(new position, true, accuracy);
73 current position.x=new position.x;
74 current position.y=new position.y;
75 }
76 g measureDevice.captureModel(model,zUpper,zLower,verResolution,latR
77 esolution);
78 g database.writeObject(folderName,projectName,objectName,model);
79 model.getPoints(vector);
80 fileName=path+objectName+".txt";
81 vector.writeToFile(fileName, model.ASCII);
83 //model.scale(model.cols()/factor, model.rows()/factor);
84 //For scaling down the object
85 //model.getPoints(vector);
86 //fileName="D:\\Wahyudin\\FileOutput\\"+"Dec 4"+objectName+".txt";
87 //fileName=path+objectName+".txt";
88 //vector.writeToFile(fileName, model.ASCII);
89 model.dispose();
90 }
91 }
```

Appendix (2)

MATLAB code for 2D Error map (Ch. 6):

```
fid=fopen(filename,'r');
 2
     SOURCE = zeros(1e5,1);
 3
     pointCounter=0;
 4
 5
    while 1
 6
 7
         readLine=fgetl(fid);
 8
         if (~ischar(readLine)) %stop when reach the EOR reading
 9
             break:
10
         end
11
12
         val=reqexp(readLine,'\t','split'); %Splitting the string with certain
13
     delimiter
14
15
         pointCounter=pointCounter+1;
16
         SOURCE (pointCounter, 1) = str2double (val (1));
17
         SOURCE(pointCounter, 2) = str2double(val(2));
18
19
     end
20
     fclose(fid);
21
     SOURCE(pointCounter+1:end,:) = []; %reduce the matrix size
22
     no of points=size(SOURCE,1);
23
24
     %Rotate the points
25
     SOURCE=MATLAB CODE rotate data(SOURCE);
26
27
     data=SOURCE;
28
    data CMM=SOURCE;
29
30
     point layout=[1 2 3 4 5 6;
31
         7 8 9 10 11 12;
32
         13 14 15 16 17 18;
33
         19 20 21 22 23 24;
34
         25 26 27 28 29 30;
35
         31 32 33 34 35 36;];
36
37
     %plotting the cmm data: HORISONTAL
38
     for i=1:6
39
         for j=1:5
40
             %plot(data(point layout(i,j):data(point layout(i,j+1),1),
41
     data(point_layout(i,j):data(point_layout(i,j+1),2),'b-', 'MarkerSize', 50);
42
             plot([data(point_layout(i,j),1)
43
     data(point_layout(i,j+1),1)],[data(point_layout(i,j),2)
44
     data(point_layout(i,j+1),2)],'b-', 'MarkerSize', 50);
45
             hold on;
46
         end
47
     end
48
49
     %plotting the cmm data: VERTICAL
50
     for j=1:6
51
         for i=1:5
52
             %plot(data(point layout(i,j):data(point layout(i,j+1),1),
53
     data(point layout(i,j):data(point layout(i,j+1),2),'b-', 'MarkerSize', 50);
```

```
54
              plot([data(point layout(i,j),1)
 55
      data(point layout(i+1,j),1)],[data(point layout(i,j),2)
 56
      data(point_layout(i+1,j),2)],'b-', 'MarkerSize', 50);
 57
              hold on;
 58
          end
 59
      end
 60
 61
      xlim([-0.1e4 2.1e4]);
 62
      ylim([-2.1e4 0.1e4]);
 63
      axis equal;
      xlabel('X/\mum');
 64
 65
      ylabel('Y/\mum');
 66
 67
 68
      %============= Data Reading =================================
 69
      fid=fopen(filename,'r');
 70
      SOURCE = zeros(1e5,1);
 71
      pointCounter=0;
 72
 73
      while 1
 74
 75
          readLine=fgetl(fid);
 76
          if (~ischar(readLine)) %stop when reach the EOR reading
 77
              break;
 78
          end
 79
 80
          val=regexp(readLine,'\t','split'); %Splitting the string with certain
 81
      delimiter
 82
 83
          pointCounter=pointCounter+1;
 84
          SOURCE(pointCounter,1) = str2double(val(1));
 85
          SOURCE(pointCounter,2) = str2double(val(2));
 86
 87
      end
 88
      fclose(fid);
 89
      SOURCE(pointCounter+1:end,:) = []; %reduce the matrix size
 90
 91
      %Rotate the points
 92
      SOURCE=MATLAB CODE rotate data(SOURCE);
 93
 94
      data=SOURCE;
 95
      data ALICONA=SOURCE;
 96
 97
      point layout=[1 2 3 4 5 6;
 98
          7 8 9 10 11 12;
 99
          13 14 15 16 17 18;
          19 20 21 22 23 24;
100
101
          25 26 27 28 29 30;
102
          31 32 33 34 35 36;];
103
104
      %Calculating difference between ALICONA and CMM centres
105
      for i=1:36
106
          delta_x(i) = data_CMM(i,1) - data_ALICONA(i,1);
107
          delta y(i) = data CMM(i,2) - data ALICONA(i,2);
108
      end
109
      amplification=50;
110
111
      %plotting the Alicona data: HORISONTAL
112
      for i=1:6
```

```
113
          for j=1:5
114
              %plot([data(point_layout(i,j),1)
115
      data(point layout(i,j+1),1)],[data(point layout(i,j),2)
116
      data(point layout(i,j+1),2)],'r-', 'MarkerSize', 50);
117
118
      plot([data(point layout(i,j),1)+delta x(point layout(i,j))*amplification
119
      data(point layout(i,j+1),1)+delta x(point layout(i,j+1))*amplification],[da
120
      ta(point layout(i,j),2)+delta y(point layout(i,j))*amplification
121
      data(point layout(i,j+1),2)+delta y(point layout(i,j+1))*amplification],'r-
122
      ', 'MarkerSize', 50);
123
              hold on;
124
          end
125
      end
126
127
      %plotting the Alicona data: VERTICAL
128
      for j=1:6
129
          for i=1:5
130
              %plot([data(point layout(i,j),1)
131
      data(point layout(i+1,j),1)],[data(point layout(i,j),2)
132
      data(point layout(i+1,j),2)],'r-', 'MarkerSize', 50);
133
134
      plot([data(point layout(i,j),1)+delta x(point layout(i,j))*amplification
135
      data(point layout(i+1,j),1)+delta x(point layout(i+1,j))*amplification],[da
136
      ta(point layout(i,j),2)+delta y(point layout(i,j))*amplification
137
      data(point layout(i+1,j),2)+delta y(point layout(i+1,j))*amplification],'r-
138
      ', 'MarkerSize', 50);
139
              hold on;
140
          end
141
      end
142
143
144
      %%%=======CALCULATE sphere distancas from ALICONA data===========
145
      %%%HORISONTAL
146
      counter=0;
147
      for i=1:6
148
          for j=1:5
149
              counter=counter+1;
150
              dist hor(counter) = sqrt(sum((data ALICONA(point layout(i,j),1) -
151
      data ALICONA(point layout(i,j+1),1))^2+(data ALICONA(point layout(i,j),2)-
152
      data ALICONA(point layout(i,j+1),2))^2));
153
          end
154
      end
155
      path='C:\ANAS error map plots\';
156
      name='10X sphere distances HORISONTAL.txt';
157
      filename=[path name];
158
      fid=fopen(filename, 'w'); %opening the file
159
      for i=1:30
160
          fprintf(fid,'%f \n', dist hor(i));
161
162
      fprintf(fid,'\n');
163
      fclose(fid);
164
165
      %%%VERTICAL
166
      counter=0;
167
      for i=1:6
168
          for j=1:5
169
              counter=counter+1;
170
              dist ver(counter) = sqrt(sum((data ALICONA(point layout(j,i),1) -
171
      data ALICONA(point layout(j+1,i),1))^2+(data ALICONA(point layout(j,i),2)-
172
      data ALICONA(point layout(j+1,i),2))^2));
```

```
173
          end
174
      end
175
      path='C:\ANAS error map plots\';
176
      name='10X sphere distances VERTICAL.txt';
177
      filename=[path name];
178
      fid=fopen(filename, 'w'); %opening the file
179
      for i=1:30
180
          fprintf(fid,'%f \n', dist ver(i));
181
      end
182
      fprintf(fid,'\n');
183
      fclose(fid);
184
185
     %%%DIAGONAL
186
     counter=0;
187
      for i=1:5 %TOP LEFT to BOTTOM RIGHT
188
          counter=counter+1;
189
          dist diag(counter) = sqrt(sum((data ALICONA(point layout(i,i),1)-
190
      data ALICONA(point layout(i+1,i+1),1))^2+(data ALICONA(point layout(i,i),2)
191
      -data ALICONA(point layout(i+1,i+1),2))^2));
192
      end
193
      col=6;
194
      for i=1:5 %TOP RIGHT to BOTTOM LEFT
195
          counter=counter+1;
196
          dist diag(counter) = sqrt(sum((data ALICONA(point layout(i,col),1) -
197
      data ALICONA (point layout (i+1, col-
198
      1),1))^2+(data ALICONA(point layout(i,col),2)-
199
      data ALICONA(point layout(i+1,col-1),2))^2));
200
          col=col-1;
201
      end
202
      path='C:\ ANAS_error_map_plots\';
203
      name='10X sphere distances DIAGONAL.txt';
204
      filename=[path name];
205
      fid=fopen(filename,'w'); %opening the file
206
      for i=1:10
207
          fprintf(fid,'%f \n', dist diag(i));
208
209
      fprintf(fid, '\n');
210
      fclose(fid);
```

Appendix (3)

MATLAB code for Rotate data (Ch. 6):

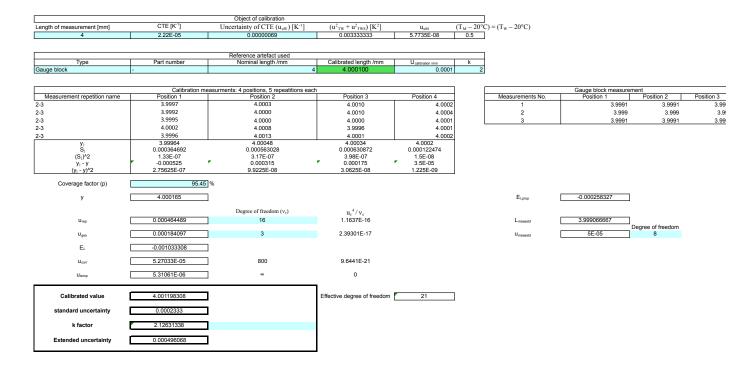
```
1
     function SOURCE transformed=MATLAB CODE rotate data(SOURCE)
 2
 3
     %line fitting
 4
     data for fitting=SOURCE(1:6,:);
 5
     data for fitting(:,3)=0; %convert the matriks into nx3 matrix
 6
 7
     %LINEAR LEAST-SQUARE LINE FITTING
 8
     %Translation of the data point to its centroid
 9
     Mraw=data for fitting; %generate M matrix nx2
10
    MrawHom=Mraw;
11
    MrawHom(:,4)=1;
12
    [n m]=size(Mraw);
13
    avgX=sum(Mraw(:,1))/n;
14
    avgY=sum(Mraw(:,2))/n;
15
     avgZ=sum(Mraw(:,3))/n;
16
    T=[1 \ 0 \ 0 \ avgX; \ 0 \ 1 \ 0 \ avgY; \ 0 \ 0 \ 1 \ avgZ; 0 \ 0 \ 0];
17
    MtranslatedHom=inv(T)*MrawHom'; %here we have to inverst T from T12 into
18
    T21=inv(T12)
19
    MtranslatedHom=MtranslatedHom';
20
    Mtranslated=[MtranslatedHom(:,1) MtranslatedHom(:,2) MtranslatedHom(:,3)];
21
22
     %fitting the line
23
     [U,S,V] = svd (Mtranslated);
24
     singularValue=S(1,1);
25
     a=V(:,1);
26
     for i=2:3
27
         if(singularValue<=S(i,i))</pre>
28
              singularValue=S(i,i);
29
              a=V(:,i);
30
         end
31
     end
32
     а
33
     a=a';
34
     %calculate the degree of rotation
35
     a ref=[1 0 0];
36
     cos angle= sum((a.*a ref))/(sqrt(sum((a).^2))*sqrt(sum((a ref).^2)))%in
37
     radian
38
     angle=acos(cos angle)
39
     cos(angle); %for verification only
40
41
     %translate to point 1 as origin
42
     for i=1:36
43
         SOURCE (i, 1) = SOURCE (i, 1) - SOURCE (1, 1);
44
         SOURCE (i, 2) = SOURCE(i, 2) - SOURCE(1, 2);
45
     end
46
47
     %rotate
48
     rot z=[\cos(angle) - \sin(angle) 0
49
         sin(angle) cos(angle) 0
50
         0 0 1
51
         ];
52
53
     %convert matrix SOURCE into nx4 format
54
     SOURCE (:, 3) = 0;
55
```

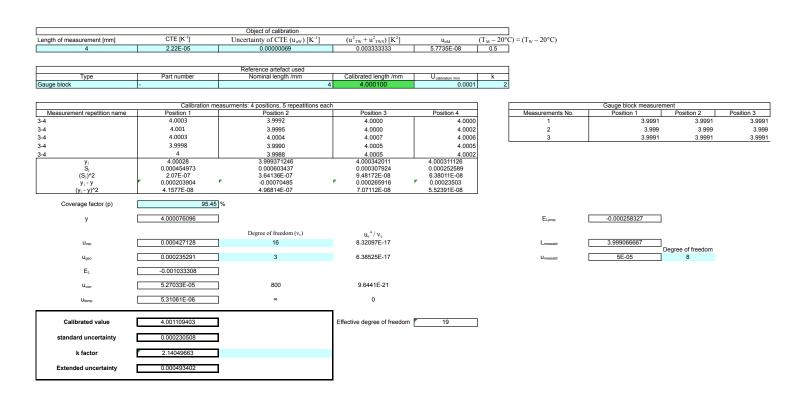
```
56
57
    temp=rot_z*SOURCE';
58
    temp=temp';
59
60
    SOURCE transformed=temp(:,1:2)
61
62
    %----- TRANSFORM the coordinate to its centroid ------
63
    %formating data points
64
    SOURCE=0;
65
    for i=1:36
66
        SOURCE(i,1) = SOURCE\_transformed(i,1);
67
        SOURCE(i,2) = SOURCE_transformed(i,2);
68
        SOURCE(i,3)=0;
69
        SOURCE (i, 4) = 1;
70
    end
71
72
    %calculate the centroid:
73
    centroid x=mean(SOURCE(:,1));
74
    centroid y=mean(SOURCE(:,2));
75
76
    dx=centroid_x-SOURCE(1,1);
77
    dy=centroid_y-SOURCE(1,2);
78
    dz=0;
79
    T12=[1 0 0 dx
80
        0 1 0 dy
81
82
        0 0 1 dz
83
        0 0 0 1];
84
85
    temp=0;
86
    temp=inv(T12) *SOURCE';
87
    temp=temp';
88
    8-----
89
    SOURCE transformed=0;
90
    SOURCE transformed=temp(:,1:2)
91
    end
```

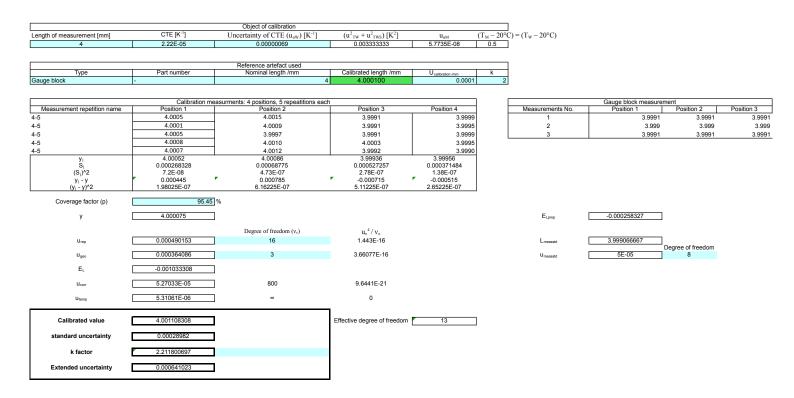
Appendix (4)

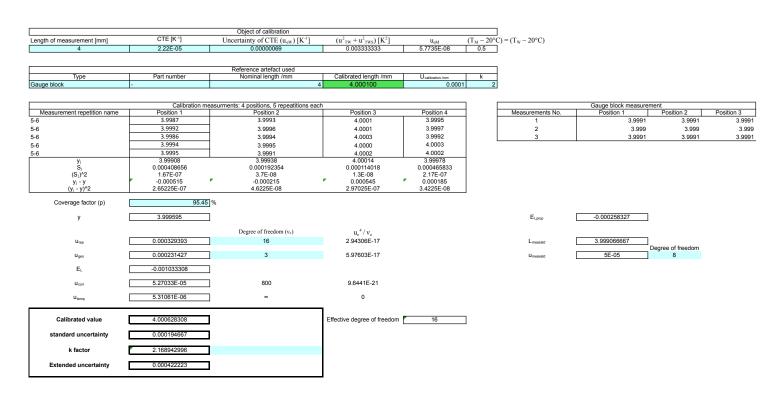
CALCULATION OF LENGTH CALIBRATION

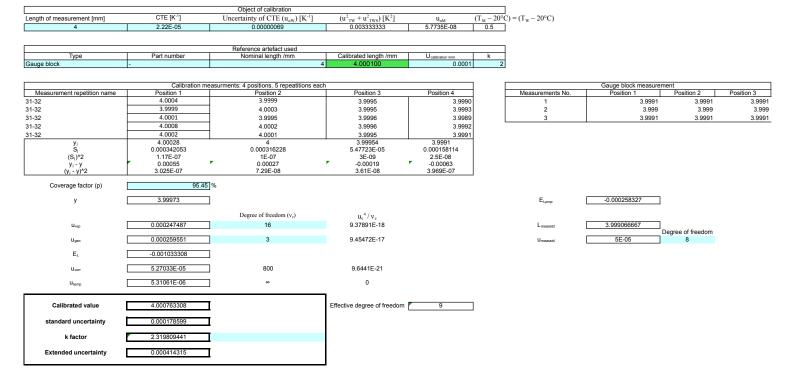
		Object of calibration				l			
Length of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{aW}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	$u_{\alpha M}$		$C) = (T_W - 20^{\circ}C)$			
4	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5				
		Reference artefact used]			
Type	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k	1			
Gauge block	-	4	4.000100	0.0001	2				
	Calibration mea	asurments: 4 positions, 5 repeatitions eac			1		Gauge block measurer		
Measurement repetition name	Position 1	Position 2	Position 3	Position 4		Measurements No.	Position 1	Position 2	Position 3
1-2	3.9998	4.0001	3.9998	3.9998		1	3.9991	3.9991	3.999
1-2	3.9999	3.9996	3.9998	3.9997	1	2	3.999	3.999	3.99
1-2	3.9999	4.0004	3.9998	4.0001		3	3.9991	3.9991	3.999
1-2	4	3.9995	4.0007	3.9999	1				
1-2	3.9999	3.9990	3.9998	4.0002	:				
y _j S _i	3.9999	3.999726899	3.999963906	3.999952915	1				
	7.07107E-05	0.00054562	0.000420551	0.000192535					
(S _j)^2	5E-09 1 40701E-05	2.97701E-07	1.76863E-07	3.70699E-08					
y _i - y	1.40701E-05 1.97967E-10	-0.000159031 2.52909E-08	7.79756E-05 6.0802E-09	6.69855E-05 4.48706E-09					
(y _j - y)^2	1.9/96/E-10	2.52909E-08	6.0802E-09	4.48706E-09	1				
Coverage factor (p)	95.45	%							
у	3.99988593					E _{Lprop}	-0.000258327		
		Degree of freedom (v _c)	u_e^4/v_e						
	0.000359386	16	u _e / V _e 4.17049E-17				3.999066667		
U _{rep}	0.000359386	16	4.17049E-17			Lmeasstd		Degree of freedom	
Ugeo	5.4815E-05	3	1.88085E-19			Umeasstd	5E-05	8	
E _i	-0.001033308								
-	5.27033E-05	222	0.0445.04						
Ucorr	5.2/033E-05	800	9.6441E-21						
U _{temp}	5.31061E-06	00	0						
Calibrated value	4.000919237			20	7				
Calibrated value	4.000919237		Effective degree of freedom	20	_				
standard uncertainty	0.000171431								
k factor	2.133028362								
Extended uncertainty	0.000365668								
<u> </u>			1						

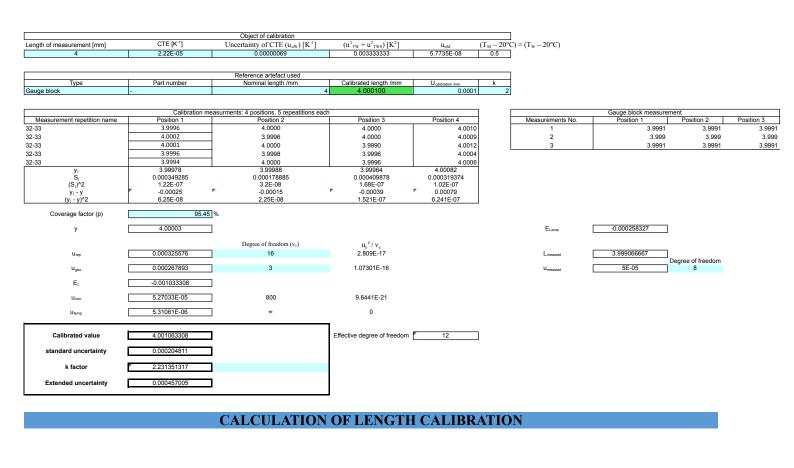


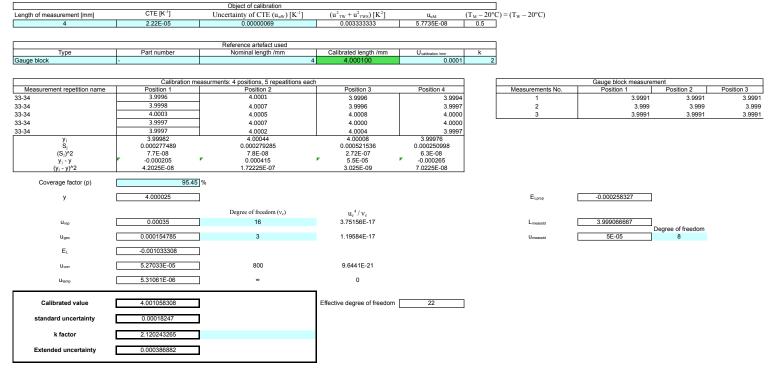


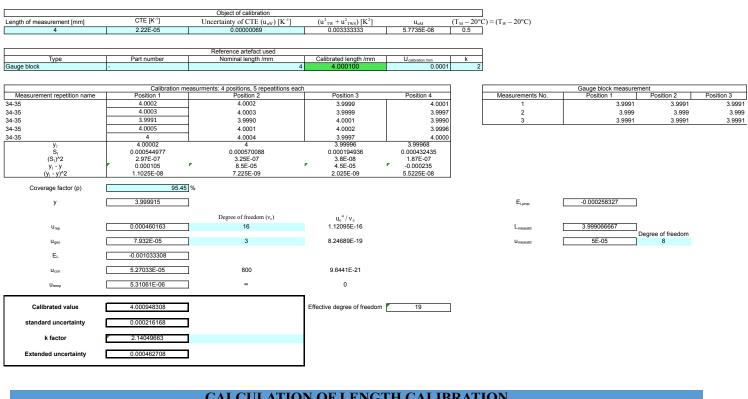


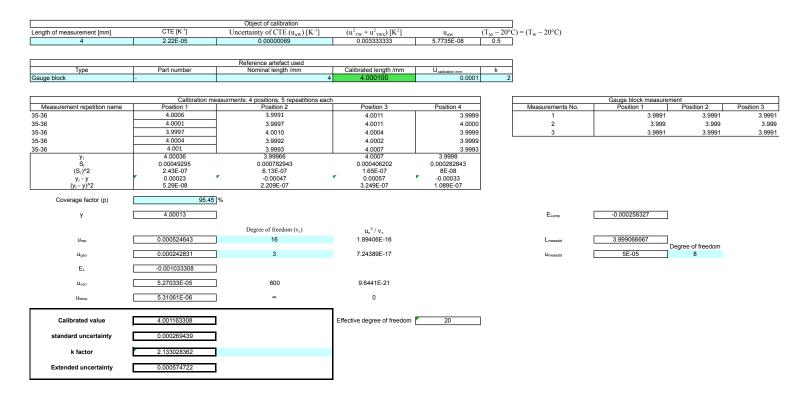


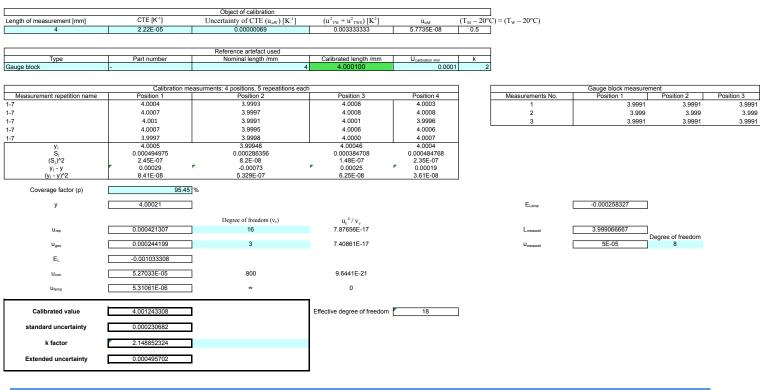


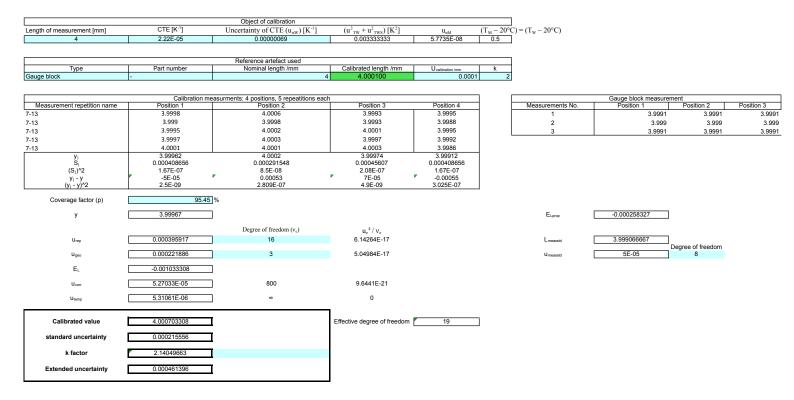












Calibrated value standard uncertainty

Extended uncertainty

CALCULATION OF LENGTH CALIBRATION

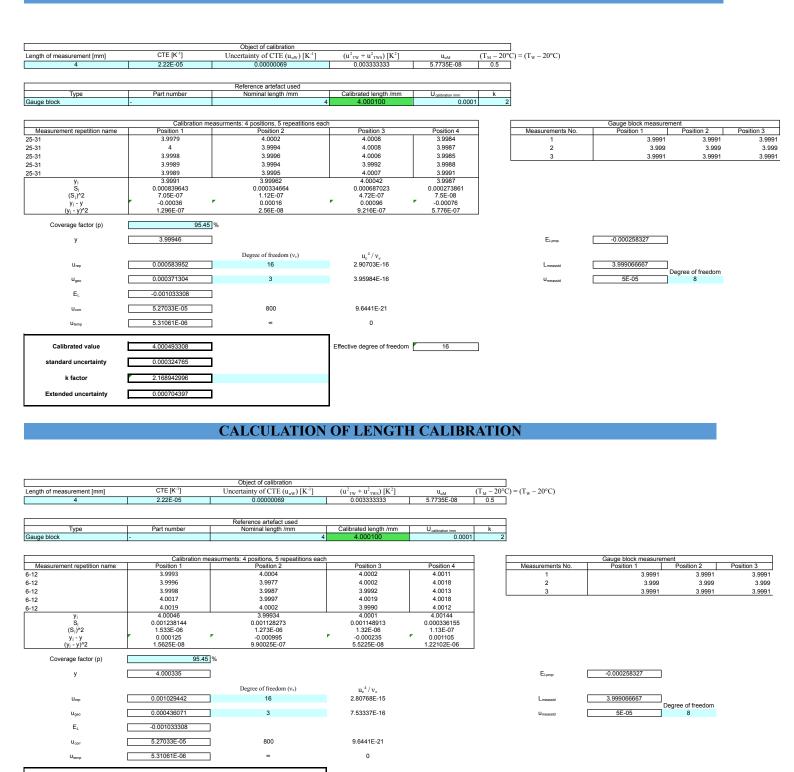
Longth of managersment [mm]	CTE [K-1]	Object of calibration Uncertainty of CTE $(u_{\alpha W})$ [K ⁻¹]	$(n^2 + n^2) \Gamma V^2$		(T 20%	$C = (T_w - 20^{\circ}C)$			
Length of measurement [mm] 4	2.22E-05	0.00000069	$(u^2_{TW} + u^2_{TWS})[K^2]$ 0.003333333	u _{αM} 5.7735E-08	0.5) - (1 _W - 20 °C)			
		Reference artefact used							
Type Gauge block	Part number	Nominal length /mm	Calibrated length /mm 4 4.000100	U _{calibration /mm})1 k				
Gauge block	-		4.000100	0.000	71 2				
	Calibration m	easurments: 4 positions, 5 repeatitions ea	ch		¬ ,		Gauge block measurement		
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	ן ו	Measurements No.	Position 1 P	osition 2	Position 3
13-19	3.9986 3.9995	3.9983 3.9995	4.0002 4.0002	3.9986 3.9983		1	3.9991	3.9991	3.
13-19 13-19	3.9988	3.9990	3.9994	3.9997		2	3.999 3.9991	3.999 3.9991	3
13-19	3.9989	3.9991	3.9995	3.9984	'				
13-19	4.0001 3.99918	3.9991 3.999	3.9994 3.99974	3.9979 3.99858					
y _i S _j	0.000614003	0.00043589	0.0004219	0.000676018					
(S ₁)^2 y ₁ - y	3.77E-07 5.5E-05	1.9E-07 -0.000125	1.78E-07 0.000615	4.57E-07 -0.000545					
(y _j - y)^2	3.025E-09	1.5625E-08	3.78225E-07	2.97025E-07					
Coverage factor (p)	95.45	7%							
						_			
у	3.999125					E _{Lprop}	-0.000258327		
		Degree of freedom (ν_e)	u_e^4 / v_e						
Urep	0.000548179	16	2.25751E-16			L _{measstd}	3.999066667	e of freedom	
Ugeo	0.000240468	3	6.96611E-17			U _{measstd}	5E-05	8	
E⊾	-0.001033308	-							
EL.		_							
Ucorr	5.27033E-05	800	9.6441E-21						
u_{temp}	5.31061E-06	_ ∞	0						
			7						
Calibrated value	4.000158308	1	Effective degree of freedom	20					
standard uncertainty	0.00027814	7							
		•							
k factor	2.133028362								
Extended uncertainty	0.000593281]							
		CALCULATION	OF LENGTH	CALIBRA	ATION	J			
		Object of calibration							
Length of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{aW}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS})[K^2]$	u _{aM} ($T_{\rm M} - 20^{\circ}{\rm C}) =$	$(T_W - 20^{\circ}C)$			
4	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5				
Туре	Part number	Reference artefact used Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
Gauge block	-	4	4.000100	0.0001	2				
Measurement repetition name	Calibration mea	asurments: 4 positions, 5 repeatitions each Position 2	Position 3	Position 4		Measurements No.	Gauge block measurement Position 1 Positio	n 2 Do	sition 3
19-25	4.0017	4.0003	3.9991	4.0022	-	1	3.9991	3.9991	3.9991
19-25	4.0007	4.0001	3.9991	4.0025		2	3.999	3.999	3.999
19-25 19-25	4.0011 4.0013	4.0002 4.0006	3.9993 4.0003	4.0020 4.0010		3	3.9991	3.9991	3.9991
19-25	4.0001	4.0006	3.9994	4.0030					
y _i S _i	4.00098 0.000609918	4.00036 0.000230217	3.99944 0.000497996	4.00214 0.00074027					
(S _j)^2	3.72E-07	5.3E-08	2.48E-07	5.48E-07					
y _i - y (y _i - y)^2	0.00025 6.25E-08	-0.00037 1.369E-07	-0.00129 1.6641E-06	0.00141 1.9881E-06					
	•								
Coverage factor (p)	95.45	7/0							
у	4.00073					E _{Lprop}	-0.000258327		
		Degree of freedom (ν_e)	u_e^4/v_e						
U _{rep}	0.000552494	16	2.32944E-16			L _{measstd}	3.999066667	roodom	
U _{geo}	0.000566539	3	2.14624E-15			U _{measstd}	Degree of fi 5E-05 8	reedom	
EL	-0.001033308								
Ucorr	5.27033E-05	800	9.6441E-21						
			0						

Effective degree of freedom 8

Calibrated value

Extended uncertainty

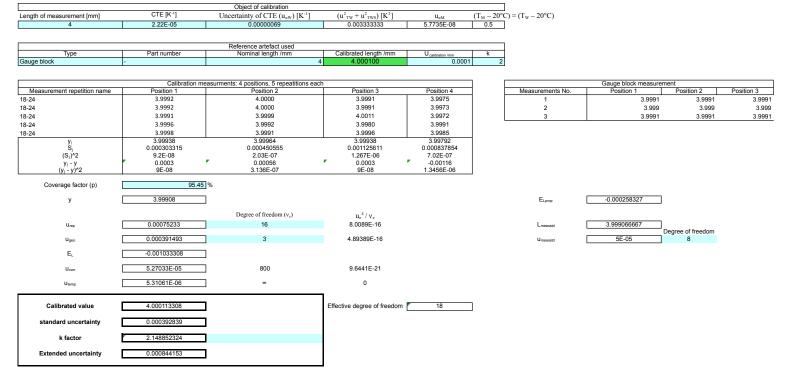
CALCULATION OF LENGTH CALIBRATION



Effective degree of freedom

19

		Object of calibration							
ength of measurement [mm]	CTE [K-1]	Uncertainty of CTE (uaW) [K-1]	$(u_{TW}^2 + u_{TWS}^2) [K^2]$	$u_{\alpha M}$	$(T_{\rm M} - 20^{\circ})$	$(C) = (T_w - 20^{\circ}C)$			
4	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5]			
		Reference artefact used				1			
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
Sauge block	-	4	4.000100	0.000	1 2				
		asurments: 4 positions, 5 repeatitions each					Gauge block measurer		
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	4	Measurements No.	Position 1	Position 2	Position 3
2-18	4.0009	4.0007	3.9995	4.0009		1	3.9991	3.9991	3.99
2-18	4.0006	4.0008	3.9995	4.0008		2	3.999	3.999	3.99
2-18	4.0007	4.0006	3.9999	4.0008		3	3.9991	3.9991	3.999
2-18	3.9991	4.0013	4.0005	3.9996					
2-18	3.999	4.0006	4.0017	4.0000					
y _j S _j	4.00006	4.0008	4.00022	4.00042					
Si	0.000928978	0.000291548 8.5E-08	0.000923038 8.52E-07	0.000584808 3.42E-07					
(S _j)^2	8.63E-07 -0.000315	0.000425	-0.000155	3.42E-07 4.5E-05					
y _i - y (y _i - y)^2	9.9225E-08	1.80625E-07	2.4025E-08	4.5E-05 2.025E-09					
					_				
Coverage factor (p)	95.45	%							
у	4.000375					E _{Lprop}	-0.000258327		
		Degree of freedom (v _c)	u_e^4/v_e						
u_{rep}	0.000731779	16	7.16901E-16			L _{measstd}	3.999066667		
U _{geo}	0.000159661	3	1.3538E-17			U _{measstd}	5E-05	Degree of freedom 8	
EL	-0.001033308								
Ucorr	5.27033E-05	800	9.6441E-21						
U _{temp}	5.31061E-06	00	0						
O temp	3.51001E-00	-	_						
Calibrated value	4.001408308		Effective degree of freedom	18	٦				
	-				_				
standard uncertainty	0.000340997								
k factor	2.148852324								
Extended uncertainty	0.000732752								
Extended differtainty	0.000/32/32								
			4						

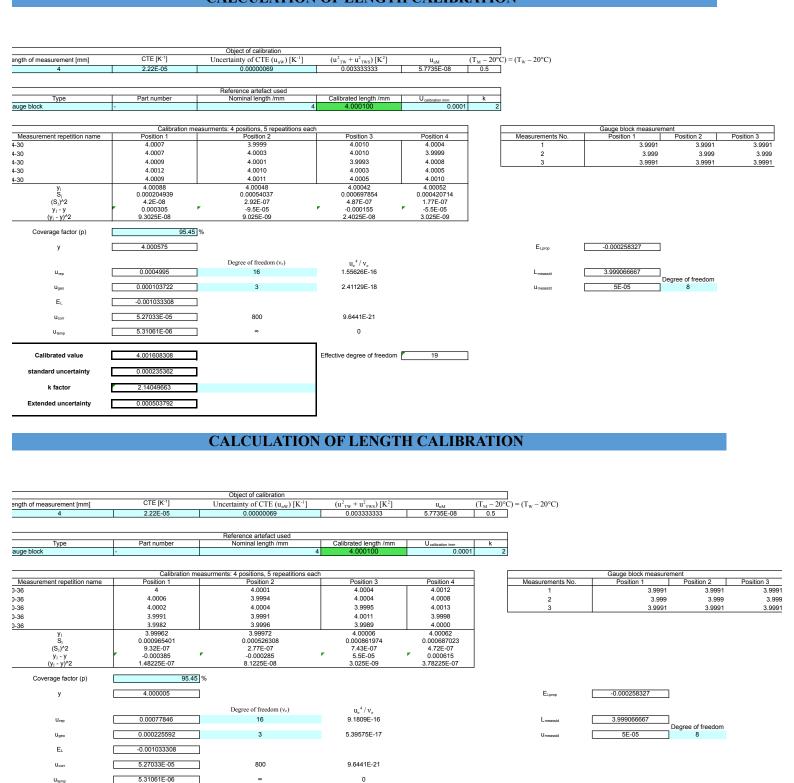


Calibrated value

standard uncertainty

Extended uncertainty

CALCULATION OF LENGTH CALIBRATION



Effective degree of freedom

5.27033E-05

5.31061E-06

U_{temp}

Calibrated value

standard uncertainty k factor Extended uncertainty 800

∞

CALCULATION OF LENGTH CALIBRATION

Length of measurement [mm]	CTE [K-1]	Object of calibration	$(n^2 + n^2) \lceil V^2 \rceil$.,	(T 20%] C) = (T _w – 20°C)			
Length of measurement (mm)	2.22E-05	Uncertainty of CTE (u _{aW}) [K ⁻¹] 0.00000069	$(u^2_{TW} + u^2_{TWS}) [K^2]$ 0.003333333	u _{aM} 5.7735E-08	0.5	(1 _w - 20 C)			
		Reference artefact used				1			
Туре	Part number	Nominal length /mm	Calibrated length /mm	U calibration /mm	k				
Gauge block	-	4	4.000100	0.000	1 2				
M		easurments: 4 positions, 5 repeatitions eac		DW 4		Management Na	Gauge block measurem		D# 0
Measurement repetition name 1-8	Position 1 5.6551	Position 2 5.6558	Position 3 5.6572	Position 4 5.6552	-	Measurements No.	Position 1 3.9991	Position 2 3.9991	Position 3 3.9
1-8	5.656	5.6559	5.6572	5.6554		2	3.999	3.999	3.
1-8	5.6562	5.6560	5.6567	5.6553		3	3.9991	3.9991	3.9
1-8	5.6563	5.6566	5.6570	5.6550					
1-8	5.6565 5.65602	5.6565 5.65616	5.6560 5.65682	5.6558 5.65534	_				
y _i S _i	0.000544977	0.000364692	0.000501996	0.000296648					
(S _j)^2	2.97E-07	1.33E-07	2.52E-07	8.8E-08					
y _j - y (y _i - y)^2	-6.5E-05 4.225E-09	7.5E-05 5.625E-09	0.000735 5.40225E-07	-0.000745 5.55025E-07					
			0.102202 01	0.000202 07					
Coverage factor (p)	95.45	<u>.</u> %							
у	5.656085					E _{Lprop}	-0.000258327		
			4 -						
	0.000400740	Degree of freedom (v _e)	u _e ⁴ /v _e				2.00000007		
U _{rep}	0.000438748	16	9.26406E-17			Lmeasstd	3.999066667	egree of freedom	
U _{geo}	0.000303466	3	1.76685E-16			U _{measstd}	5E-05	8	
E∟	-0.001033308	7							
C _L	-0.001033300	_							
U _{corr}	5.27033E-05	800	9.6441E-21						
U _{temp}	5.31061E-06	_ ∞	0						
			-						
Calibrated value	5.657118308	٦	Effective degree of freedom	15	_				
Canbratoa Talao			Encoure acgree or necount						
standard uncertainty	0.000253631]							
k factor	2.181165682								
		_							
Extended uncertainty	0.000553212]							
			OFIENCE		. ATTE	. .			
		CALCULATION	OF LENGTH	1 CALIBR	ATIO	N			
Length of measurement [mm]	CTE [K-1]	Object of calibration Uncertainty of CTE (u _{aW}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	$u_{\alpha M}$	(T _v = 20°C)	$= (T_W - 20^{\circ}C)$			
4	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5	(-w == +)			
		Reference artefact used							
Туре	Part number	Nominal length /mm	Calibrated length /mm	U calibration /mm	k				
Gauge block	-	4	4.000100	0.0001	2				
	0.17. 17				. –				
Measurement repetition name	Calibration me Position 1	easurments: 4 positions, 5 repeatitions each Position 2	Position 3	Position 4	F	Measurements No.	Gauge block measuremen Position 1	Position 2	Position 3
8-15	5.6575	5.6559	5.6562	5.6574		1	3.9991	3.9991	3.999
8-15	5.6573	5.6557	5.6562	5.6577		2	3.999	3.999	3.999
8-15	5.6569	5.6564	5.6572	5.6574	L	3	3.9991	3.9991	3.999
8-15 9-15	5.6569 5.6561	5.6556 5.6557	5.6560 5.6578	5.6580 5.6577					
8-15 y _i	5.65694	5.65586	5.65668	5.6577 5.65764					
y _j S _j	0.000536656	0.000320936	0.000782304	0.000250998					
(S _j)^2 y _j - y	2.88E-07 0.00016	1.03E-07 -0.00092	6.12E-07 -1E-04	6.3E-08 0.00086					
(y _j - y)^2	2.56E-08	8.464E-07	1E-08	7.396E-07					
Coverage factor (p)	95.45	1%							
		ı ···							
у	5.65678	I				E _{Lprop}	-0.000258327		
		Degree of freedom (v _c)	u_e^4/v_e						
U _{rep}	0.000516236	16	1.77556E-16			L _{measstd}	3.999066667		
u_{geo}	0.000367605	3	3.80438E-16			U _{measstd}	Deς 5Ε-05	ree of freedom 8	
	•								
E∟	-0.001033308								

Effective degree of freedom 14

9.6441E-21

0

		Object of calibration							
gth of measurement [mm]	CTE [K-1]	Uncertainty of CTE (uaw) [K-1]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	$u_{\alpha M}$		$(C) = (T_w - 20^{\circ}C)$			
4	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5	J			
						_			
Torre	Part number	Reference artefact used	Calibrated Investo (see	I 11	1.				
Type ige block	- Fait fluffiber	Nominal length /mm 4	Calibrated length /mm 4.000100	U _{calibration /mm} 0.0001	k 2				
						•			
	Calibration mos	asurments: 4 positions, 5 repeatitions each			1		Gauge block measurer	mont	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	ł	Measurements No.	Position 1	Position 2	Position 3
22	5.6573	5.6579	5.6579	5.6570	ĺ	1	3.9991	3.9991	3.9991
22	5.6569	5.6573	5.6579	5.6563		2	3.999	3.999	3.999
22	5.6565	5.6567	5.6568	5.6574		3	3.9991	3.9991	3.9991
22	5.6573	5.6573 5.6574	5.6575 5.6564	5.6562 5.6554					
22 V:	5.6575 5.6571	5.65732	5.6573	5.65646					
y _j S _i	0.0004	0.000426615	0.000674537	0.000773305					
(S _j)^2	1.6E-07	1.82E-07	4.55E-07	5.98E-07					
y _i - y (y _i - y)^2	5.5E-05 3.025E-09	0.000275 7.5625E-08	0.000255 6.5025E-08	-0.000585 3.42225E-07					
	0.023E-03	1.5025E-00	0.50202-00	0.42220L-01	J				
Coverage factor (p)	95.45	%							
у	5.657045					E _{Lprop}	-0.000258327		
,						4			
		Degree of freedom (v _e)	u_e^4/v_e						
U _{rep}	0.000590551	16	3.04066E-16			L _{measstd}	3.999066667	D	
u_{geo}	0.000201225	3	3.41578E-17			Umazerte	5E-05	Degree of freedom 8	
Ggeo		, and the second	0.110102 11			O meassid	0L 00	ū	
E∟	-0.001033308								
II	5.27033E-05	800	9.6441E-21						
U _{corr}	3.27033E-03	000	5.0441L-21						
U _{temp}	5.31061E-06	00	0						
			İ						
Calibrated value	5.658078308		Effective degree of freedom	20	1				
				,					
standard uncertainty	0.000287539								
k factor	2.133028362								
Extended uncertainty	0.000613329								
		CALCULATION	LODEDNICE	TT CATIO		037			
		Object of calibration							
ength of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{aW}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	u_{aM}		$(T_W - 20^{\circ}C)$			
4	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5				
						_			
Туре	Part number	Reference artefact used Nominal length /mm	Calibrated length /mm	U calibration /mm	k	_			
auge block	-		4 4.000100	0.000		2			
	'	•		•		_			
	Calibration m	easurments: 4 positions, 5 repeatitions ea	ch		7		Gauge block measur	ement	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4		Measurements No.	Position 1	Position 2	Position 3
2-29	5.656	5.6565	5.6566	5.6559		1	3.9991		3.999
2-29	5.6559	5.6574	5.6566	5.6574		2	3.999		3.99
2-29	5.6566 5.6562	5.6569 5.6572	5.6573 5.6564	5.6557 5.6572		3	3.9991	3.9991	3.999
2-29 2-29	5.6563	5.6569	5.6576	5.6578					
y _i	5.6562	5.65698	5.6569	5.6568					
S _j (S _j)^2	0.000273861 7.5E-08	0.000342053 1.17E-07	0.000519615 2.7E-07	0.000940744 8.85E-07					
(S _j)-2 V _i - V	-0.00052	0.00026	0.00018	8E-05					
y _i - y (y _i - y)^2	2.704E-07	6.76E-08	3.24E-08	6.4E-09					
Coverage factor (p)	95.45	∏%							
covolago lacio. (p)	·							_	
у	5.65672	_				E _{Lprop}	-0.000258327		
		Degree of freedom (v _e)	u_e^4/ν_e						
U _{rep}	0.000580302	16	2.83501E-16			L _{measstd}	3.999066667	7	
								Degree of freedom	
U _{geo}	0.0001772	3	2.05408E-17			U _{measstd}	5E-05	8	
EL	-0.001033308]							
Ucorr	5.27033E-05	800	9.6441E-21						
Gor		-							
U _{temp}	5.31061E-06	∞ ∞	0						
			7						
Calibrated value	5.657753308]	Effective degree of freedom	n 20					
etandard uncertaint	0.000270205	7							
standard uncertainty	0.000279295	4							
k factor	2.133028362								
	0.000595745	7							
Extended uncertainty									

5.27033E-05

5.31061E-06

U_{temp}

Calibrated value

standard uncertainty k factor Extended uncertainty 800 ∞

CALCULATION OF LENGTH CALIBRATION

		Object of calibration]			
ength of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{aW}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	$u_{\alpha M}$		$C) = (T_W - 20^{\circ}C)$			
4	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5				
						-			
Туре	Part number	Reference artefact used Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	l k				
Gauge block	-		4 4.000100	0.000					
	•	•				-			
	Calibration n	neasurments: 4 positions, 5 repeatitions each	ch		7 1		Gauge block measurem	ent	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4		Measurements No.	Position 1	Position 2	Position 3
9-36 9-36	5.6579 5.6587	5.6574 5.6570	5.6579 5.6579	5.6579 5.6561		1 2	3.9991 3.999	3.9991 3.999	3.999
9-36	5.658	5.6576	5.6560	5.6578		3	3.9991	3.9991	3.99
29-36	5.6569	5.6572	5.6576	5.6558	'				
9-36	5.6566	5.6574	5.6561	5.6559					
y _j S _i	5.65762 0.000858487	5.65732 0.000228035	5.6571 0.000966954	5.6567 0.001055936					
(S _j)^2	7.37E-07	5.2E-08	9.35E-07	1.115E-06					
y _i - y (y _i - y)^2	0.000435 1.89225E-07	0.000135 1.8225E-08	-8.5E-05 7.225E-09	-0.000485 2.35225E-07					
Coverage factor (p)	95.4	5]%							
y	5.657185					E _{Lprop}	-0.000258327		
		Degree of freedom (v _e)	4 /						
U _{rep}	0.000842467	16	u _e ⁴ / v _e 1.25936E-15			L _{measstd}	3.999066667		
Siep	-							egree of freedom	
U _{geo}	0.000193628	3	2.92839E-17			U _{measstd}	5E-05	8	
EL	-0.001033308								
	5.27033E-05	800	9.6441E-21						
Ucorr									
U _{temp}	5.31061E-06	∞ ∞	0						
			7						
Calibrated value	5.658218308]	Effective degree of freedom	18					
standard uncertainty	0.000392592	٦							
Standard uncertainty	0.000392392	_							
k factor	2.148852324]							
Extended uncertainty									
	0.000843623	7							
Extended uncertainty	0.000843623								
Extended uncertainty	0.000843623	<u> </u>							
Extended discontainty	0.000843623	CALCIII ATIONI	OF LENGTH	CALIDD	ATION	.T			
Extended uncertainty	0.000843623	CALCULATION	OF LENGTH	CALIBRA	ATION	V			
Extended uncording	0.000843623	CALCULATION	OF LENGTH	CALIBRA	ATION	V			
Extended uncordainty	0.000843623	CALCULATION	OF LENGTH	CALIBRA	ATION	N			
Exercised direct daility	0.000843623	CALCULATION	OF LENGTH	CALIBRA	ATION	N			
Exercised uncortainty	0.000843623		OF LENGTH	CALIBRA	ATION	N			
ngth of measurement [mm]	0.000843623	CALCULATION Object of calibration Uncertainty of CTE $(u_{aw})[K^{-1}]$	OF LENGTH $(u^{2}_{TW} + u^{2}_{TWS})[K^{2}]$		ATION T _M - 20°C) =				
		Object of calibration							
ngth of measurement [mm]	CTE [K ⁻¹]	Object of calibration	$(u_{TW}^2 + u_{TWS}^2) [K^2]$	u_{aM} (T _M – 20°C) =				
ngth of measurement [mm] 4	CTE [K ⁺] 2.22E-05	Object of calibration Uncertainty of CTE $(u_{aW})[K^{-1}]$ 0.00000069	$ \frac{\left(u^2_{TW} + u^2_{TWS}\right)\left[K^2\right]}{0.003333333} $	u _{sM} (5.7735E-08	$T_{M} - 20^{\circ}C) = 0.5$				
ngth of measurement [mm] 4 Type	CTE [K ⁻¹]	Object of calibration Uncertainty of CTE $(u_{ew})[K^{-1}]$ 0.00000069	$ \frac{\left(u^2_{\rm TW} + u^2_{\rm TWS}\right) \left[K^2\right]}{0.003333333} $ Calibrated length /mm	U _{aM} (5.7735E-08	T _M – 20°C) =				
ngth of measurement [mm] 4	CTE [K ⁺] 2.22E-05	Object of calibration Uncertainty of CTE $(u_{ww})[K^{-1}]$ 0.0000069	$ \frac{\left(u^2_{TW} + u^2_{TWS}\right)\left[K^2\right]}{0.003333333} $	u _{sM} (5.7735E-08	$T_{M} - 20^{\circ}C) = 0.5$				
ngth of measurement [mm] 4 Type	CTE [K ³] 2.22E-05 Part number	Object of calibration Uncertainty of CTE (u_{eW}) [K^{-1}] 0.0000069 Reference artefact used Nominal length /mm 4	$ \frac{\left(u^2_{\rm TW} + u^2_{\rm TWS}\right) \left[K^2\right]}{0.003333333} $ Calibrated length /mm	U _{aM} (5.7735E-08	$T_{M} - 20^{\circ}C) = 0.5$		Gauge block measurement		
ngth of measurement [mm] 4 Type	CTE [K¹] 2.22E-05 Part number Calibration mea	Object of calibration Uncertainty of CTE $(u_{aw})[K^{-1}]$ 0.0000069 Reference artefact used Nominal length /mm 4	(u² _{TW} + u² _{TWS}) [K²] 0.0033333333 Calibrated length /mm 4.000100	U _{eM} (5.7735E-08 Ucalibration Imm 0.0001	$T_{M} - 20^{\circ}C) = 0.5$				osition 3
ngth of measurement [mm] 4 Type uge block	CTE [K-1] 2.22E-05 Part number Calibration mea Position 1 5.6563	Object of calibration Uncertainty of CTE (u_ew) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 4 surrments: 4 positions, 5 repeatitions each Position 2 5.6575	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 4.000100 Position 3 5.6561	U _{califoration Imm} (5.7735E-08) U_califoration Imm	$T_{M} - 20^{\circ}C) = 0.5$	F (T _w – 20°C) Measurements No.	Position 1 P 3.9991	3.9991	3.9991
ngth of measurement [mm] 4 Type uge block	CTE [K ⁻¹] 2.22E-05 Part number Calibration mea Position 1 5.6563 5.6571		(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 4.000100 Position 3 5.6561 5.6561	U _{sM} (5.7735E-08 U calibration from 0.0001 Position 4 5.6582 5.6584	$T_{M} - 20^{\circ}C) = 0.5$	(T _w - 20°C) Measurements No.	Position 1 P 3.9991 3.999	3.9991 3.999	3.9991 3.999
ngth of measurement [mm] 4 Type uge block	CTE [K-1] 2.22E-05 Part number Calibration mea Position 1 5.6563	Object of calibration Uncertainty of CTE (u_{ew}) [K^{-1}] 0.00000069 Reference artefact used Nominal length /mm 4 usurments: 4 positions, 5 repeatitions each Position 2 5.6575	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 4.000100 Position 3 5.6561	U _{califoration Imm} (5.7735E-08) U_califoration Imm	$T_{M} - 20^{\circ}C) = 0.5$	F (T _w – 20°C) Measurements No.	Position 1 P 3.9991	3.9991	3.9991
ngth of measurement [mm] 4 Type uge block Measurement repetition name 1 1 1 1 1	CTE [K ⁻¹] 2.22E-05 Part number Calibration mea Position 1 5.6563 5.6571 5.6465 5.6582 5.6574	Object of calibration Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.0000069 Reference artefact used Nominal length /mm 4 surments: 4 positions, 5 repeatitions each Position 2 5.6575 5.6560 5.6560 5.6570 5.6574	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 4.000100 Position 3 5.6561 5.6561 5.6563 5.6563 5.6595 5.6570	U _{collibration from} U-collibration from 0.00001 Position 4 5.6582 5.6584 5.6580 5.6593 5.6593	$T_{M} - 20^{\circ}C) = 0.5$	(T _w - 20°C) Measurements No.	Position 1 P 3.9991 3.999	3.9991 3.999	3.9991 3.999
ngth of measurement [mm] 4 Type uge block Measurement repetition name 1 1 1 1 1	CTE [K ⁻¹] 2.22E-05 Part number Calibration mea Position 1 5.6563 5.6571 5.6465 5.6582 5.6574 5.6551	Object of calibration Uncertainty of CTE (u_ew) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 4 usurments: 4 positions, 5 repeatitions each Position 2 5.6575 5.6560 5.6560 5.6570 5.6574 5.65678	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 4.000100 Position 3 5.6561 5.6561 5.6563 5.6565 5.6565 5.6570 5.6568	U _{calibration Imm} U calibration Imm 0.00001 Position 4 5.6582 5.6584 5.6580 5.6593 5.6581	$T_{M} - 20^{\circ}C) = 0.5$	(T _w - 20°C) Measurements No.	Position 1 P 3.9991 3.999	3.9991 3.999	3.9991 3.999
Type Uge block Measurement repetition name 1 1 1 1 (S), (S), '2	CTE [K ⁻¹] 2.22E-05 Part number Calibration mee Position 1 5.6563 5.6571 5.6465 5.6582 5.6574 5.6551 0.004855409 2.3575E-05	Object of calibration Uncertainty of CTE (u _{eW}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 4 surments: 4 positions, 5 repeatitions each Position 2 5.6575 5.6560 5.6570 5.6560 5.6570 5.65674 5.65678 0.000736206 5.42E-07	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 4.000100 Position 3 5.6561 5.6561 5.6563 5.6563 5.6565 5.6568 0.001019804 1.04E-06	U _{sM} (5.7735E-08 Usationation Imm 0.0001 Position 4 5.6582 5.6584 5.6580 5.6593 5.6581 5.6581 5.6584 0.000524404 2.75E-07	$T_{M} - 20^{\circ}C) = 0.5$	(T _w - 20°C) Measurements No.	Position 1 P 3.9991 3.999	3.9991 3.999	3.9991 3.999
mgth of measurement [mm] 4 Type uge block Measurement repetition name 1 1 1 1 5 (S,)'22 y, - y	CTE [K ⁻¹] 2.22E-05 Part number Calibration mea Position 1 5.6563 5.6571 5.6465 5.6582 5.6574 5.6551 0.004855409 2.3575E-05 -0.00167	Object of calibration Uncertainty of CTE (u _{ew}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 4 surments: 4 positions, 5 repeatitions each Position 2 5.6575 5.6560 5.6560 5.6570 5.6574 5.65678 0.000736206 5.42E-07 1E-05	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm	U _{sM} (5.7735E-08 U _{calibration Imm} 0.0001 Position 4 5.6582 5.6584 5.6584 5.6581 5.6581 5.6584 $T_{M} - 20^{\circ}C) = 0.5$	(T _w - 20°C) Measurements No.	Position 1 P 3.9991 3.999	3.9991 3.999	3.9991 3.999	
mgth of measurement [mm] 4 Type uge block Measurement repetition name 1 1 1 1 5 (S,)'22 y,'-y (y,-y)'2	CTE [K ⁻¹] 2.22E-05 Part number Calibration mea Position 1 5.6563 5.65671 5.6465 5.6582 5.6574 5.8551 0.004855409 2.3575E-05 -0.00167 2.7889E-06	Object of calibration Uncertainty of CTE (u _{ew}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 4 surments: 4 positions, 5 repeatitions each Position 2 5.6575 5.6560 5.6570 5.6574 5.65678 0.000736206 5.42E-07 1E-05 1E-10	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 4.000100 Position 3 5.6561 5.6561 5.6563 5.6563 5.6565 5.6568 0.001019804 1.04E-06	U _{sM} (5.7735E-08 Usationation Imm 0.0001 Position 4 5.6582 5.6584 5.6580 5.6593 5.6581 5.6581 5.6584 0.000524404 2.75E-07	$T_{M} - 20^{\circ}C) = 0.5$	(T _w - 20°C) Measurements No.	Position 1 P 3.9991 3.999	3.9991 3.999	3.9991 3.999
mgth of measurement [mm] 4 Type uge block Measurement repetition name 1 1 1 1 1 5 (S,)'2 y, - y	CTE [K ⁻¹] 2.22E-05 Part number Calibration mea Position 1 5.6563 5.6571 5.6465 5.6582 5.6574 5.6551 0.004855409 2.3575E-05 -0.00167	Object of calibration Uncertainty of CTE (u _{ew}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 4 surments: 4 positions, 5 repeatitions each Position 2 5.6575 5.6560 5.6570 5.6574 5.65678 0.000736206 5.42E-07 1E-05 1E-10	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm	U _{sM} (5.7735E-08 U _{calibration Imm} 0.0001 Position 4 5.6582 5.6584 5.6584 5.6581 5.6581 5.6584 $T_{M} - 20^{\circ}C) = 0.5$	(T _w - 20°C) Measurements No.	Position 1 P 3.9991 3.999	3.9991 3.999	3.9991 3.999	
mgth of measurement [mm] 4 Type uge block Measurement repetition name 1 1 1 1 1 5 (S))'22 Y, - Y (Y, - Y)'2	CTE [K ⁻¹] 2.22E-05 Part number Calibration mea Position 1 5.6563 5.65671 5.6465 5.6582 5.6574 5.8551 0.004855409 2.3575E-05 -0.00167 2.7889E-06	Object of calibration Uncertainty of CTE (u _{ew}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 4 surments: 4 positions, 5 repeatitions each Position 2 5.6575 5.6560 5.6570 5.6574 5.65678 0.000736206 5.42E-07 1E-05 1E-10	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm	U _{sM} (5.7735E-08 U _{calibration Imm} 0.0001 Position 4 5.6582 5.6584 5.6584 5.6581 5.6581 5.6584 $T_{M} - 20^{\circ}C) = 0.5$	(T _w - 20°C) Measurements No.	Position 1 P 3.9991 3.999	3.9991 3.999	3.9991 3.999	
mgth of measurement [mm] 4 Type uge block Measurement repetition name 1 1 1 5, (S,)'2 y, - y (y, - y)'2 Coverage factor (p)	CTE [K*] 2.22E-05 Part number Calibration mes Position 1 5.6563 5.6571 5.6465 5.6582 5.6574 5.6551 0.004855409 2.3375E-05 -0.00167 2.7889E-06	Object of calibration Uncertainty of CTE (u _{eW}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 4 surments: 4 positions, 5 repeatitions each Position 2 5.6575 5.6560 5.6570 5.6560 5.6570 5.65678 0.000736206 5.42E-07 1E-05 1E-10	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 4.000100 Position 3 5.6561 5.6561 5.6563 5.6563 5.6565 5.6570 5.6568 0.001019804 1.04E-06 3E-05 9E-10	U _{sM} (5.7735E-08 U _{calibration Imm} 0.0001 Position 4 5.6582 5.6584 5.6584 5.6581 5.6581 5.6584 $T_{M} - 20^{\circ}C) = 0.5$	Measurements No.	Position 1 P 3.9991 3.9991	3.9991 3.999	3.9991 3.999	
mgth of measurement [mm] 4 Type uge block Measurement repetition name 1 1 1 1 5 (S ₁)*2 y ₁ - y (y ₁ - y)*2 Coverage factor (p)	CTE [K-1] 2.22E-05 Part number Calibration mea Position 1 5.6563 5.6571 5.6465 5.6582 5.6574 5.6551 0.004855409 2.3575E-05 -0.00167 2.7889E-06 95.45] 5.65677	Object of calibration Uncertainty of CTE (u_w) [K¹] 0.00000069 Reference artefact used Nominal length /mm 4 summents: 4 positions, 5 repeatitions each Position 2 5.6575 5.6560 5.6560 5.6570 5.6574 5.65678 0.000736206 5.42E-07 1E-05 1E-10	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm	U _{sM} (5.7735E-08 U _{calibration Imm} 0.0001 Position 4 5.6582 5.6584 5.6584 5.6581 5.6581 5.6584 $T_{M} - 20^{\circ}C) = 0.5$	Measurements No. 1 2 3	Position 1	3.9991 3.999	3.9991 3.999	
Type uge block Measurement repetition name 1 1 1 1 1 S (S)*2 Y -Y (Y -Y)*2 Coverage factor (p) y Ump	CTE [K ⁻¹] 2.22E-05 Part number Calibration mea Position 1 5.6563 5.6571 5.6465 5.6582 5.6574 5.6551 0.00485409 2.3375E-05 -0.00167 2.7889E-06 95.45] 5.66677	Object of calibration Uncertainty of CTE (u _{ww}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 4 surments: 4 positions, 5 repeatitions each Position 2 5.6575 5.6560 5.6560 5.6570 5.6574 5.65678 0.000738206 5.42E-07 1E-05 1E-10 Degree of freedom (v _e)	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm	U _{sM} (5.7735E-08 U _{calibration Imm} 0.0001 Position 4 5.6582 5.6584 5.6584 5.6581 5.6581 5.6584 $T_{M} - 20^{\circ}C) = 0.5$	Measurements No. 1 2 3 ELprop [Lmeassed [Position 1	3.9991 3.999 3.9991	3.9991 3.999	
mgth of measurement [mm] 4 Type uge block Measurement repetition name 1 1 1 1 1 5 (S), '22 Y, - Y (Y, - Y)'2 Coverage factor (p) y	CTE [K-1] 2.22E-05 Part number Calibration mea Position 1 5.6563 5.6571 5.6465 5.6582 5.6574 5.6551 0.004855409 2.3575E-05 -0.00167 2.7889E-06 95.45] 5.65677	Object of calibration Uncertainty of CTE (u_w) [K¹] 0.00000069 Reference artefact used Nominal length /mm 4 summents: 4 positions, 5 repeatitions each Position 2 5.6575 5.6560 5.6560 5.6570 5.6574 5.65678 0.000736206 5.42E-07 1E-05 1E-10	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm	U _{sM} (5.7735E-08 U _{calibration Imm} 0.0001 Position 4 5.6582 5.6584 5.6584 5.6581 5.6581 5.6584 $T_{M} - 20^{\circ}C) = 0.5$	Measurements No. 1 2 3	Position 1	3.9991 3.999 3.9991	3.9991 3.999	

9.6441E-21

Effective degree of freedom 18

		Object of calibration									
ength of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{aW}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS})[K^2]$	u _{aM}		$T(T_{\rm W} - 20^{\circ} C)$)				
4	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5						
		Reference artefact used									
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k						
auge block	-	4	4.000100	0.000	1 2						
	Calibration measu	rments: 4 positions, 5 repeatitions each			ا ر			Gauge blo	ck measuremen		
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	1	Measureme	nts No.	Position	11	Position 2	Position 3
1-16 1-16	5.6557 5.6557	5.6541 5.6561	5.6559 5.6559	5.6545 5.6545		1 2			3.9991 3.999	3.9991 3.999	3.999 ⁻ 3.999
1-16	5.6558	5.6579	5.6568	5.6549		3			3.9991	3.9991	3.999
1-16	5.6564	5.6555	5.6563	5.6552							
1-16 y _i	5.6574 5.6562	5.6556 5.65584	5.6561 5.6562	5.6552 5.65486	+						
y _i S _i (S _j)^2	0.000731437 5.35E-07	0.001370401 1.878E-06	0.000374166 1.4E-07	0.000350714 1.23E-07							
y _i - y	0.000425	6.5E-05	0.000425	-0.000915							
(y _j - y)^2	1.80625E-07	4.225E-09	1.80625E-07	8.37225E-07							
Coverage factor (p)	95.45 %										
у	5.655775					E _{Lprop}	,	-0.000258	3327		
,		D 66 1 ()	4 :								
U _{rep}	0.000817924	Degree of freedom (v _e) 16	u _e ⁴ / v _e 1.1189E-15			L _{meass}		3.999066	667		
									Deg	ree of freedom	
U _{geo}	0.000316583	3	2.09272E-16			U _{meass}	td	5E-05		8	
EL	-0.001033308										
U _{corr}	5.27033E-05	800	9.6441E-21								
U _{temp}	5.31061E-06	eo	0								
Utemp	5.31001E-00		U								
Calibrated value	5.656808308		Effective degree of freedom	19	7						
Odiibrated Value			Elicolive degree of freedom	10							
standard uncertainty	0.000402072										
k factor	2.14049663										
Extended uncertainty	0.000860634										
Extended uncertainty	0.000000034										
igth of measurement [mm]	CTE [K-1]	Object of calibration Uncertainty of CTE $(u_{\alpha W})$ [K		[K ²] ι	$\Pi_{\alpha M}$	(T _M – 20°C)	$= (T_W - 20^\circ)$	°C)			
4	2.22E-05	0.00000069	0.00333333	5.77	35E-08	0.5					
		5.									
Туре	Part number	Reference artefact used Nominal length /mm	Calibrated length	/mm U _{calit}	oration /mm	k					
uge block	-		4 4.000100		0.0001						
		easurments: 4 positions, 5 repeatition								lock measureme	
Measurement repetition name 21	Position 1 5.6574	Position 2 5.6578	Position 3 5.6576		6578	 	Measurer		Positi	on 1 3.9991	Position 2 3.999
21	5.6572	5.6566	5.6576		6570			2		3.999	3.99
21	5.6572	5.6557	5.6579	5.0	6575			3		3.9991	3.999
21	5.6565	5.6569	5.6571		6571						
21 V:	5.656 5.65686	5.6570 5.6568	5.6580 5.65764		6574 55736	1					
y _i S _i	0.000589915	0.000758288	0.000350714	1 0.000	320936						
(S _j)^2 y _i - y	3.48E-07 -0.000305	5.75E-07 -0.000365	1.23E-07 0.000475	7.0 7 0.0	3E-07 00195						
(y _j - y)^2	9.3025E-08	1.33225E-07	2.25625E-07	3.80	25E-08						
Coverage factor (p)	95.45	1%									
		1									
У	5.657165	J					EL	prop	-0.0002	58327	
		Degree of freedom (ve)	u_e^4/ν_e								
U _{rep}	0.000535957] 16	2.06281E-16	6			Lme	asstd	3.9990	66667	
U _{geo}	0.000202052	3	3.47225E-17	,			Ume	anatel	5E-		egree of freedon 8
		,	0.47 ZZ0L-17				Ume	ne profit			
E∟		-									
U _{corr}	-0.001033308]									
	-0.001033308 5.27033E-05]] 800	9.6441E-21								
U _{temp}	5.27033E-05	•									
	•] 800] ∞	9.6441E-21 0								
Calibrated value	5.27033E-05 5.31061E-06	•	0	rreedom P	20	1					
Calibrated value	5.27033E-05	•		rreedom	20]					
Calibrated value	5.27033E-05 5.31061E-06	•	0	reedom	20]					
standard uncertainty	5.27033E-05 5.31061E-06 5.658198308 0.000265447	•	0	reedom -	20	1					
standard uncertainty	5.27033E-05 5.31061E-06 5.658198308 0.000265447 2.133028362	•	0	reedom -	20]					
standard uncertainty	5.27033E-05 5.31061E-06 5.658198308 0.000265447	•	0	reedom	20]					

Extended uncertainty

0.000638823

		Object of calibration				1		
Length of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{aW}) [K ⁻¹] 0.00000069	$(u^2_{TW} + u^2_{TWS}) [K^2]$	u _{aM}		$(C) = (T_W - 20^{\circ}C)$		
4	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5			
		Reference artefact used]		
Type Gauge block	Part number	Nominal length /mm	Calibrated length /mm 4 4.000100	U _{calibration /mm} 0.0001	k			
Oddge block			4.000100	0.0001		1		
		neasurments: 4 positions, 5 repeatitions ea]		Gauge block measurement	
Measurement repetition nan 21-26	ne Position 1 5.6571	Position 2 5.6575	Position 3 5.6573	Position 4 5.6564	-	Measurements No.	Position 1 Position 3.9991	n 2 Position 3 3.9991 3.9
21-26	5.6566	5.6581	5.6573	5.6569		2	3.999	3.999 3
21-26 21-26	5.6567 5.6577	5.6576 5.6580	5.6561 5.6566	5.6563 5.6566		3	3.9991	3.9991 3.9
21-26	5.6585	5.6581	5.6565	5.6565				
y _j S _j	5.65732 0.00078867	5.65786 0.000288097	5.65676 0.000527257	5.65654 0.000230217				
(S _j)^2	6.22E-07	8.3E-08	2.78E-07	5.3E-08				
y _j - y (y _i - y)^2	0.0002 4E-08	0.00074 5.476E-07	-0.00036 1.296E-07	-0.00058 3.364E-07				
Coverage factor (p)	95.45	51%			_			
						_	0.00050007	
у	5.65712					E _{Lprop}	-0.000258327	
	0.00050000	Degree of freedom (v _e)	u _e ⁴ /v _e				2 00000007	
U _{rep}	0.00050892	16	1.67703E-16			Lmeasstd	3.999066667 Degree of fi	reedom
u_{geo}	0.000296311	3	1.60601E-16			U _{measstd}	5E-05 8	
EL	-0.001033308							
Ucorr	5.27033E-05	800	9.6441E-21					
U _{temo}	5.31061E-06	· ·	0					
-temp			_					
Calibrated value	5.658153308	٦	Effective degree of freedom	17				
standard uncertainty	0.000276687	7						
		_						
k factor	2.158263401							
Extended uncertainty	0.000597164	ם						
		CALCULATION	OF LENGTH	I CALIBR	ATIO	N		
		CALCULATION	OF LEMOTI	ICALIDA	AIIO	11		
		Object of calibration						
gth of measurement [mm]	CTE [K-1]	Uncertainty of CTE (uaW) [K-1]	$(u^2_{TW} + u^2_{TWS})[K^2]$			$= (T_w - 20^{\circ}C)$		
4	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5			
		Reference artefact used						
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k			
ige block	-	4	4.000100	0.0001	2			
	Calibration mea	surments: 4 positions, 5 repeatitions each	1		г		Gauge block measurement	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4		Measurements No.	Position 1 Position	
31 31	5.6562 5.6569	5.6574 5.6562	5.6560 5.6560	5.6575 5.6577		1 2	3.9991 3.999	3.9991 3.9 3.999 3
31	5.6568	5.6561	5.6562	5.6573		3		3.9991 3.9
31	5.6567 5.6548	5.6566 5.6567	5.6569 5.6565	5.6577 5.6579				
31 y _i	5.65628	5.6566	5.65632	5.65762				
y _i S _i (S _i)^2	0.000870057 7.57E-07	0.000514782 2.65E-07	0.000383406 1.47E-07	0.000228035 5.2E-08				
y _i - y (y _i - y)^2	-0.000425 1.80625E-07	-0.000105 1.1025E-08	-0.000385 1.48225E-07	0.000915 8.37225E-07				
	•		1.402232-07	0.072202-07				
Coverage factor (p)	95.45	6						
у	5.656705					E_{Lprop}	-0.000258327	
		Degree of freedom (ν_e)	$u_e^{\ 4}/\nu_e$					
U _{rep}	0.000552494	16	2.32944E-16			L _{measstd}	3.999066667 Degree of fr	reedom
u_{geo}	0.000313196	3	2.00458E-16			U _{measstd}	5E-05 8	
EL	-0.001033308							
Ucorr	5.27033E-05	800	9.6441E-21					
U _{temp}	5.31061E-06	00	0					
Calibrated value	5.657738308		Effective degree of freedom	18				
			souve degree or recodiff	10				
standard uncertainty	0.000297286							
k factor	2.148852324							

Appendix (5)

		Object of calibration]		
gth of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{aW}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS}) [K^2]$ 0.003333333	u _{aM}		$(C) = (T_w - 20^{\circ}C)$		
0.75	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5	_		
		Reference artefact used				1		
Туре	Part number	Nominal length /mm	Calibrated length /mm	U calibration /mm	k			
ige block	-	0.7	0.500000	0.000	1 2			
	Calibration me	asurments: 4 positions, 5 repeatitions ead	th .		7		Gauge block measurement	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4		Measurements No.	Position 1 Position 2	Position 3
	0.750000 0.750300	0.749800 0.749400	0.748600 0.748200	0.747900 0.748200		1 2	0.5009 0.5009 0.5013 0.5013	0.500 0.501
	0.749500	0.749200	0.748300	0.748001		3	0.5002 0.5002	0.500
	0.749300 0.749200	0.749200 0.749900	0.748500 0.748700	0.748200 0.748400				
y _j	0.749660181	0.749500037	0.748460116	0.748140168	-			
S _j (S _j)^2	0.000472347 2.23111E-07	0.000331646 1.09989E-07	0.000207365 4.30003E-08	0.000194879 3.79778E-08				
y _i - y	0.000720056	0.000559912 3.13501E-07	-0.00048001	-0.000799957				
(y _i - y)^2	5.1848E-07		2.30409E-07	6.39932E-07				
Coverage factor (p)	95.45	%						
у	0.748940126					E_{Lprop}	0.0016	
		Degree of freedom (ve)	u_e^4/v_e					
u_{rep}	0.000321745	16	2.67908E-17			L _{measstd}	0.5008	
Ugeo	0.000376643	3	4.19256E-16			Umeasstd	Degree of freedom 0.000482183 8	
EL	0.0012							
			4.545005.40					
Ucorr	0.000252488	9	4.51562E-16					
U _{temp}	9.95739E-07	60	0					
Calibrated value	0.747740400			46	_			
Calibrated value	0.747740126		Effective degree of freedom	16				
standard uncertainty	0.000346295							
k factor	2.168942996							
Extended uncertainty	0.000751093							
	,							
		CALCULATION	OF LENGTH	I CALIBR	ATIO	N		
-th -f t []	CTE [K-1]	Object of calibration	(2 2) [IV2]		(T 200C)	- (T 209C)		
gth of measurement [mm] 0.75	2.22E-05	Uncertainty of CTE (u _{aW}) [K ⁻¹] 0.00000069	$(u^2_{TW} + u^2_{TWS}) [K^2]$ 0.003333333	u _{aM} 5.7735E-08	0.5	$= (T_W - 20^{\circ}C)$		
					<u>.</u>			
Time	Dort number	Reference artefact used	Calibrated langth /mm		k			
Type ige block	Part number	Nominal length /mm 0.75	Calibrated length /mm 0.500000	U calibration /mm 0.0001	2			
Measurement repetition name	Calibration mea	surments: 4 positions, 5 repeatitions each Position 2	Position 3	Position 4	F	Measurements No.	Gauge block measurement Position 1 Position 2 Po	sition 3
Medadiement repetition name	0.748900	0.751400	0.750000	0.750000		1	0.5009 0.5009	0.5009
	0.748600 0.749100	0.751201 0.751400	0.750100 0.750100	0.749700 0.749901		2 3	0.5013 0.5013 0.5002 0.5002	0.5013 0.5002
	0.749400	0.751400	0.750300	0.750100		3	0.3002 0.3002	0.3002
	0.749400 0.74908012	0.750801 0.751200588	0.749900 0.750080231	0.750000 0.749940423				
y _j S _j	0.000342135	0.000244817	0.000148367	0.000151626				
(S _j)^2 y _j - y	1.17056E-07 -0.00099522	5.99356E-08 0.001125248	2.20129E-08 4.89016E-06					
(y _j - y)^2	9.90464E-07	1.26618E-06	2.39137E-11	1.82028E-08				
Coverage factor (p)	95.45	%						
у	0.75007534					E _{Lprop}	0.0016	
		Degree of freedom (v _e)	u_e^4/v_e					
U _{rep}	0.000235582	16	7.70028E-18			L _{measstd}	0.5008	
							Degree of freedom	
Ugeo		3	7.48705E-16			U _{measstd}		
u _{geo}	0.0004354	3	7.48705E-16			Umeasstd	0.000482183	
EL	0.0004354					Umeasstd		
	0.0004354 0.0012 0.000252488	9	4.51562E-16			Umeastd		
EL	0.0004354					Umeasstd		
E _L U _{corr} U _{temp}	0.0004354 0.0012 0.000252488 9.95739E-07	9	4.51562E-16 0	40		U meassid		
E _L U _{corr}	0.0004354 0.0012 0.000252488 9.95739E-07 0.748875340	9	4.51562E-16	12		Umessatd		
E _L U _{corr} U _{temp}	0.0004354 0.0012 0.000252488 9.95739E-07	9	4.51562E-16 0	12		Umeasatd		
E _L U _{corr} U _{temp} Calibrated value	0.0004354 0.0012 0.000252488 9.95739E-07 0.748875340	9	4.51562E-16 0	12		Umeasatd		
E _L U _{corr} U _{temp} Calibrated value standard uncertainty	0.0004354 0.0012 0.000252488 9.95739E-07 0.748875340 0.000349634	9	4.51562E-16 0	12		Umeasatd		

		Object of calibration]			
ength of measurement [mm]	CTE [K-1]	Uncertainty of CTE (uaw) [K-1]	$(u^2_{TW} + u^2_{TWS})[K^2]$	$u_{\alpha M}$	$(T_{M} - 20^{\circ})$	$^{\circ}C) = (T_{W} - 20^{\circ}C)$			
0.75	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5	7 ` "			
	•	•	•	•	•	-			
		Reference artefact used				1			
Туре	Part number	Nominal length /mm	Calibrated length /mm	U calibration /mm	l k	1			
auge block	-	0.7		0.0001	2	1			
						_			
	Calibration m	easurments: 4 positions, 5 repeatitions each	th.		1		Gauge block measurem	ent	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	†	Measurements No.	Position 1	Position 2	Position 3
-4	0.750600	0.749900	0.750800	0.751300	1	1	0.5009	0.5009	0.5
-4	0.750400	0.749702	0.750900	0.751300		2	0.5013	0.5013	0.5
-4	0.750400	0.750300	0.750900	0.750900		3	0.5002	0.5002	0.5
-4	0.750400	0.750700	0.750700	0.751300					
<u>-4</u>	0.750600 0.750480125	0.750501 0.750220611	0.750800 0.750820119	0.751200 0.751200053	4				
y _i S _i	0.000109567	0.000414324	8.3764E-05	0.000173219					
(S _j)^2	1.20049E-08	1.71664E-07	7.01641E-09	3.0005E-08					
y _i - y	-0.000200102	-0.000459616	0.000139892	0.000519826					
(y _j - y)^2	4.00407E-08	2.11247E-07	1.95697E-08	2.70219E-07	_				
Coverage factor (p)	95.45	7%							
		-							
у	0.750680227]				E _{Lprop}	0.0016		
		Degree of freedom (v _e)	u_e^4/ν_e						
	0.000234889	16	7.61005E-18			L	0.5008		
U_{rep}	0.000204000	10	7.01000E-10			Lmeasstd	0.0000	egree of freedom	
U _{geo}	0.000212343	3	4.23559E-17			U _{measstd}	0.000482183	8	
	0.0012	7							
E∟	0.0012	7							
Ucorr	0.000252488	9	4.51562E-16						
		7	•						
U _{temp}	9.95739E-07	_ ∞	0						
			7						
Calibrated value	0.749480227	Ī	Effective degree of freedom	14	1				
		- -			_				
standard uncertainty	0.000293356	l							
k factor	2.195291287	ī							
Ridetoi	2.100231207								
Extended uncertainty	0.000644003	I							
	·-	_	<u> 1</u>						
		CALCULATION	OF LENGTH	I CALIRRA	ATIO	N			
		Object of calibration							
ength of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{aW}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	u _{αM} (*	T _M – 20°C)	$= (T_W - 20^{\circ}C)$			
0.75	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5				
-		Reference artefact used							
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
auge block	-	0.75	0.500000	0.0001	2				
	Calibration me	asurments: 4 positions, 5 repeatitions each					Gauge block measurement		
Measurement repetition name	Position 1	Position 2	Position 3	Position 4		Measurements No.	Position 1 F	Position 2	Position 3
-5	0.750800 0.751100	0.749800	0.751100	0.749500		1	0.5009	0.5009	0.5009
-5 -5	0.751100	0.750600 0.749800	0.750900 0.750600	0.749700 0.749600		2 3	0.5013 0.5002	0.5013 0.5002	0.5013 0.5002
-5	0.750800	0.749800	0.750700	0.749600		•	0.3002	0.0002	0.3002
.5	0.750400	0.749800	0.751100	0.749600					
y _i S _i	0.750840073	0.749960029	0.750880177	0.749600207					
S _j (S _j)^2	0.000288061 8.29793E-08	0.000357754 1.27988E-07	0.000228007 5.19872E-08	7.07367E-05 5.00368E-09					
y ₁ - y	0.000519952	-0.000360092		-0.000719915					
(y _j - y)^2	2.7035E-07	1.29666E-07	3.13662E-07	5.18277E-07					
Coverage factor (p)	95.45	%							
Goverage factor (p)	30.40	70							
у	0.750320122					E _{Lprop}	0.0016		
		D	4 ,						
	0.000259924	Degree of freedom (v _c)	u _e ⁴ /v _e				0.5000		
U _{rep}	0.000258824	16	1.1219E-17				0.5008 Degr	ee of freedom	
u_{geo}	0.000320411	3	2.19577E-16			U _{measstd}	0.000482183	8	
	0.0040								
EL	0.0012								
U _{corr}	0.000252488	9	4.51562E-16						
II.	9.95739E-07	00	0						
U _{temp}	3.33133L=01	-	v						
Calibrated value	0.749120122		Effective degree of freedom	15					
standard uncertainty	0.000320647								
y									
k factor	2.181165682								
Eutonded	0.00000005								
Extended uncertainty	0.000699385								

		Object of calibration]			
gth of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{aW}) [K ⁻¹]	$(u_{TW}^2 + u_{TWS}^2) [K^2]$	$u_{\alpha M}$		$C) = (T_W - 20^{\circ}C)$			
0.75	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5]			
		Reference artefact used				1			
Туре	Part number	Nominal length /mm	Calibrated length /mm	U calibration /mm	k				
ige block	-	0.75	0.500000	0.0001	2				
	Calibration mea	surments: 4 positions, 5 repeatitions each	1		1		Gauge block measurem	ent	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	1	Measurements No.	Position 1	Position 2	Position 3
	0.749500 0.749300	0.750400 0.749900	0.749000 0.749600	0.749500 0.749600		1 2	0.5009 0.5013	0.5009 0.5013	0.5009 0.5013
	0.749400	0.750100	0.750000	0.750100		3	0.5002	0.5002	0.5002
	0.749900 0.749900	0.750000	0.749401	0.749700					
y _i	0.749600047	0.749800 0.750040055	0.749200 0.749440249	0.750000 0.749780141	1				
y _i S _j (S _j)^2	0.00028287 8.00157E-08	0.00023023 5.30059E-08	0.000384783 1.48058E-07	0.00025876 6.69567E-08					
y _i - y	-0.000115076	0.000324932	-0.000274874	6.50183E-05					
(y _j - y)^2	1.32426E-08	1.05581E-07	7.55555E-08	4.22738E-09	J				
Coverage factor (p)	95.45 %	6							
у	0.749715123					E _{Lprop}	0.0016		
		Degree of freedom (v _e)	u_e^4/ν_e						
U _{rep}	0.000294973	16	1.89264E-17			L _{measstd}	0.5008		
II.	0.000128649	3	5.70665E-18			U _{measstd}	0.000482183	egree of freedom 8	
u _{geo}		ű	5.76005E-10			O measstd	0.000402100	Ü	
EL	0.0012								
Ucorr	0.000252488	9	4.51562E-16						
U _{temp}	9.95739E-07	∞	0						
			7						
Calibrated value	0.748515123		Effective degree of freedom	15					
standard uncertainty	0.000292045								
-									
k factor	2.181165682								
Extended uncertainty	0.000636999								
		CALCULATION			ATI	7. T			
		CALCULATION	OF LENGII	n CALIDN	AII	JIN			
gth of measurement [mm]	CTE [K-1]	Object of calibration Uncertainty of CTE (u _{gW}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS})[K^2]$	u_{aM}	(T = 20°] C) = (T _w – 20°C)			
0.75	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5]			
Torr	Dest sumber	Reference artefact used	Calibrated Investo (see	1 11	1 1]			
Type ige block	Part number	Nominal length /mm 0.75	Calibrated length /mm 0.500000	U _{calibration /mm} 0.0001	k 2				
						-			
		surments: 4 positions, 5 repeatitions each		5 " 1]		Gauge block measurem		5
Measurement repetition name 32	Position 1 0.749600	Position 2 0.750301	Position 3 0.750000	Position 4 0.750400		Measurements No.	Position 1 0.5009	Position 2 0.5009	Position 3 0.5009
32	0.750500	0.750401	0.749300	0.750601		2	0.5013	0.5013	0.5013
32 32	0.749300 0.749900	0.750100 0.749700	0.749600 0.750100	0.750500 0.750600		3	0.5002	0.5002	0.5002
32	0.749900	0.749500	0.750300	0.750300					
y _i S _j	0.749840051 0.000445006	0.750000317 0.000387505	0.749860245 0.000403857	0.750480242 0.000130469					
(S _j)^2	1.98031E-07	1.5016E-07	1.63101E-07	1.70221E-08					
y _i - y (y _i - y)^2	-0.000205163 4.2092E-08	-4.48967E-05 2.01571E-09	-0.000184969 3.42134E-08	0.000435029 1.8925E-07					
Coverage factor (p)	95.45 %	6			-				
	0.750045214					-	0.0040		
у	0.750045214					E _{Lprop}	0.0016		
		Degree of freedom (ve)	u_e^4/v_e						
U _{rep}	0.000363426	16	4.36117E-17			Lmeasstd	0.5008	egree of freedom	
U _{geo}	0.000149324	3	1.0358E-17			U _{measstd}	0.000482183	8	
EL	0.0012								
Ucorr	0.000252488	9	4.51562E-16						
	9.95739E-07	80	0						
U _{temp}	9.907.39E-U7		U -						
Calibrated value	0.748845214		Effective degree of freedom	18	1				
			Zcouve degree of freedom		1				
standard uncertainty	0.000309421								
k factor	2.148852324								
Extended uncertainty	0.000664899								

Calibrated value

standard uncertainty
k factor
Extended uncertainty

CALCULATION OF LENGTH CALIBRATION

						-			
gth of measurement [mm]	CTE [K-1]	Object of calibration Uncertainty of CTE (u _{aW}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS})[K^2]$	u_{aM}	(T _M – 20°	C) = (T _w – 20°C)			
0.75	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5				
		5.6				7			
Туре	Part number	Reference artefact used Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
ige block	-	0.75	0.500000	0.0001	1 2				
					-				
Measurement repetition name	Calibration meas Position 1	urments: 4 positions, 5 repeatitions each Position 2	Position 3	Position 4	1	Measurements No.	Gauge block measurement Position 1 Pro	osition 2	Position 3
33	0.748400	0.750500	0.749200	0.749001	1	1	0.5009	0.5009	0.500
33 33	0.748800 0.749200	0.750500 0.751100	0.749400 0.749400	0.748500 0.748900		2 3	0.5013 0.5002	0.5013 0.5002	0.501 0.500
33	0.748600	0.751600	0.749300	0.748801			0.3002	0.0002	0.500
33	0.749000 0.748800105	0.751400 0.751020025	0.749100 0.749280056	0.748800 0.748800479	4				
y _j S _j	0.000316253	0.000506943	0.00013033	0.000187289					
(S _j)^2 y _j - y	1.00016E-07 -0.000675061	2.56991E-07 0.001544859	1.69858E-08 -0.000195111	3.50772E-08 -0.000674687					
(y _i - y)^2	4.55707E-07	2.38659E-06	3.80681E-08	4.55203E-07					
Coverage factor (p)	95.45 %								
у	0.749475167					E _{Lprop}	0.0016		
,		B	4.4						
11	0.000319793	Degree of freedom (v _e) 16	u _e ⁴ / v _e 2.61466E-17			L _{measstd}	0.5008		
U _{rep}							Degre	e of freedom	
U _{geo}	0.000527223	3	1.60967E-15			U _{measstd}	0.000482183	8	
E∟	0.0012								
U _{corr}	0.000252488	9	4.51562E-16						
U _{temp}	9.95739E-07	00	0						
Clemp	0.00100201		· ·						
Calibrated value	0.748275167		Effective degree of freedom	11	٦				
standard uncertainty	0.00039204			,	_				
k factor	2.254866004								
Extended uncertainty	0.000883998								
		CALCULATION	N OF LENGT	TH CALIB	RATI	ION			
		Object of calibration							
Length of measurement [mm] 0.75	CTE [K-1] 2.22E-05	Uncertainty of CTE (u _{aW}) [K ⁻¹] 0.00000069	$(u^2_{TW} + u^2_{TWS})[K^2]$ 0.003333333	u _{aM} 5.7735E-08	$(T_M - 2)$	$0^{\circ}C) = (T_{w} - 20^{\circ}C)$			
0.73	2.22E-03	0.0000003	0.00333333	3.7733E=00	0.5				
		Reference artefact used							
Type Gauge block	Part number	Nominal length /mm 0.1	Calibrated length /mm 75 0.500000	U calibration /mm)01 k	2			
Gaage blook		J	0.00000	0.00	,,,,	-			
		easurments: 4 positions, 5 repeatitions ea					Gauge block measurement		
Measurement repetition name 33-34	Position 1 0.75090006	Position 2 0.7499	Position 3 0.7506	Position 4 0.7512	_	Measurements No.	Position 1 0.5009	Position 2 0.5009	Position 3 0.50
33-34	0.750800007	0.7498	0.7504	0.7513		2	0.5013	0.5013	0.50
33-34	0.750600107 0.750800107	0.7494	0.7502	0.7519		3	0.5002	0.5002	0.50
33-34 33-34	0.750800107	0.7491 0.7499	0.7506 0.7504	0.7513 0.7515					
y _i S _i	0.750780077	0.749620323	0.750440087	0.751440444					
(S _j)^2	0.000109527 1.19962E-08	0.000356077 1.26791E-07	0.000167356 2.8008E-08	0.0002794 7.80646E-08					
y _j - y (y _i - y)^2	0.000209844 4.40347E-08	-0.00094991 9.02329E-07	-0.000130146 1.6938E-08	0.000870212 7.57268E-07					
	•								
Coverage factor (p)	95.45	J /º							
у	0.750570233	J				E _{Lprop}	0.0016		
		Degree of freedom (v _e)	u_e^4/v_e						
U _{rep}	0.000247417	16	9.36818E-18			L _{measstd}	0.5008	ee of freedom	
U _{geo}	0.000378657	3	4.28293E-16			Umeasstd	0.000482183	8	
EL	0.0012]							
U _{corr}	0.000252488] 9	4.51562E-16						
		_							
U _{temp}	9.95739E-07	∞	0						

		Object of calibration				٦		
gth of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{aw}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	$u_{\alpha M}$	(T _M - 20°	$^{\circ}C) = (T_{W} - 20^{\circ}C)$		
0.75	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5]		
		Reference artefact used				7		
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k			
ige block	-	0.75	0.500000	0.0001	2	2]		
		surments: 4 positions, 5 repeatitions each		5			Gauge block measurement	- · · · · ·
Measurement repetition name 35	Position 1 0.750000	Position 2 0.749900	Position 3 0.750900	Position 4 0.748900		Measurements No.	Position 1 Position 2 0.5009 0.5009	Position 3 0.5009
35	0.749300	0.750200	0.751100	0.749300		2	0.5009 0.5009	0.5013
35	0.749400	0.749900	0.751400	0.749200		3	0.5002 0.5002	0.5002
35	0.749400	0.749600	0.750700	0.749500			•	
35	0.749200	0.750000	0.750800	0.749500				
y _j S _j	0.749460072 0.000313146	0.749920168 0.000216644	0.750980185 0.00027756	0.749280125 0.000249015				
(S _j)^2	9.80602E-08	4.69346E-08	7.70395E-08	6.20083E-08				
y _i - y	-0.000450066	1.00304E-03	0.001010011	-0.000630012				
(y _i - y)^2	2.02559E-07	1.00609E-10	1.145E-06	3.96915E-07	l			
Coverage factor (p)	95.45	%						
	0.740040400					-	0.0046	
у	0.749910138					E _{Lprop}	0.0016	
		Degree of freedom (ve)	u_e^4/ν_e					
U _{rep}	0.000266478	16	1.26063E-17			L _{measstd}	0.5008	
	0.000004000	2	4.400000 40				Degree of freedom	
U _{geo}	0.000381289	3	4.40328E-16			U _{measstd}	0.000482183 8	
EL	0.0012							
	0.000050400	0	4 545605 40					
U _{corr}	0.000252488	9	4.51562E-16					
U _{temp}	9.95739E-07	∞	0					
Calibrated value	0.748710138		Effective degree of freedom	14	l			
			, i					
standard uncertainty	0.000338081							
k factor	2.195291287							
N Idoloi	2.100201201							
Extended uncertainty	0.000742185							
		G I I GIII I MIGI	· OP · PNOP	~				
		CALCULATION	N OF LENGT	H CALIBI	KATI	ION		
		Object of calibration						
ength of measurement [mm]	CTE [K-1]	Uncertainty of CTE (uaW) [K-1]	$(u_{TW}^2 + u_{TWS}^2) [K^2]$	$u_{\alpha M}$	$(T_{M} - 20)$	$0^{\circ}C) = (T_{W} - 20^{\circ}C)$		
0.75	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5			
		Reference artefact used						
Type	Part number	Nominal length /mm 0.7	Calibrated length /mm 5 0.500000	U calibration /mm 0.000	k	2		
auge block	-	0.7	3 0.00000	0.000	1			
	Calibratian a				_		O blask	
Measurement repetition name		easurments: 4 positions, 5 repeatitions ea Position 2	Position 3	Position 4	_	Measurements No.	Gauge block measurement Position 1 Position 2	Position 3
5-36	0.750300	0.750400	0.749200	0.749900		1	0.5009 0.5009	0.500
5-36	0.750900	0.749900	0.749500	0.749700		2	0.5013 0.5013	0.501
5-36	0.750900	0.750500	0.749500	0.749700		3	0.5002 0.5002	0.500
5-36	0.751001	0.750100	0.749600	0.749500				
5-36	0.751100 0.750840285	0.750100	0.749700	0.749500	_			
y _i S _j	0.000313199	0.750200136 0.000244888	0.749500064 0.000187111	0.749660088 0.000167295				
(S _j)^2	9.80938E-08	5.997E-08	3.50107E-08	2.79875E-08				
y _i - y (y _i - y)^2	0.000790142 6.24324E-07	0.000149993 2.24978E-08	-0.000550079 3.02587E-07	-0.000390055 1.52143E-07				
(y _j - y) 2	0.24324E-07	2.243702-00	3.02307 L=07	1.32 143L=01	_			
Coverage factor (p)	95.45	%						
у	0.750050143	1				E _{Lprop}	0.0016	
,		_				— грюр		
		Degree of freedom (ve)	u_e^4 / v_e					
U _{rep}	0.000235086	16	7.63568E-18			L _{measstd}	0.5008	
U _{geo}	0.000302979	3	1.75552E-16			U _{measstd}	Degree of freedom 0.000482183 8	
		-						
E⊾	0.0012	J						
Ucorr	0.000252488	9	4.51562E-16					
	0 0F720F 07	- ∞	0					
U _{temp}	9.95739E-07	□ 50	0					
			_					
0-86		-			_			
Calibrated value	0.748850143]	Effective degree of freedom	15				
]	Effective degree of freedom	15				
Calibrated value standard uncertainty	0.748850143 0.000312655	1	Effective degree of freedom	15				
]]	Effective degree of freedom	15				
standard uncertainty	0.000312655]]]	Effective degree of freedom	15				

9.95739E-07

Calibrated value

standard uncertainty

Extended uncertainty

CALCULATION OF LENGTH CALIBRATION

-th -f	CTE [K-1]	Object of calibration	(2 2) [IV 2]		(T 2000	T) = (T 200C)			
gth of measurement [mm] 0.75	2.22E-05	Uncertainty of CTE (u _{aW}) [K ⁻¹] 0.00000069	$(u^2_{TW} + u^2_{TWS}) [K^2]$ 0.003333333	u _{aM} 5.7735E-08	0.5	$T(C) = (T_W - 20^{\circ}C)$			
0.70	Z.ZZZ 00	0.0000000	0.00000000	0.17002 00	0.0				
		Reference artefact used							
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
ige block	-	0.75		0.000					
	Calibration mea	asurments: 4 positions, 5 repeatitions each	1		7 [Gauge block measuremen	nt	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4		Measurements No.	Position 1	Position 2	Position 3
	0.749500327	0.7498	0.7488	0.7504		1	0.5009	0.5009	0.500
	0.749300107 0.750000007	0.7496 0.7508	0.7494 0.7490	0.7499 0.7496		2	0.5013 0.5002	0.5013 0.5002	0.50° 0.500
	0.749600107	0.7504	0.7490	0.7496		<u> </u>	0.5002	0.3002	0.500
	0.74930006	0.7503	0.7500	0.7497					
y _j S _j	0.749540121 0.000288059	0.750180077 0.000481698	0.749240436 0.000477585	0.749840675 0.000336088					
(S _i)^2	8.29782E-08	2.32032E-07	2.28088E-07	1.12955E-07					
y _i - y	-0.000160206	0.00047975	-0.000459891	0.000140347					
(y _i - y)^2	2.5666E-08	2.3016E-07	2.115E-07	1.96974E-08					
Coverage factor (p)	95.45	%							
V	0.749700327					E _{Lprop}	0.0016		
у	0.749700327					Lprop	0.0010		
		Degree of freedom (ve)	u_e^4/v_e						
U _{rep}	0.000404986	16	6.72509E-17			L _{measstd}	0.5008		
u_{geo}	0.000201458	3	3.43159E-17			U _{measstd}	0.000482183	gree of freedom 8	
		•				-meassiu	0.000.00	_	
EL	0.0012								
U _{corr}	0.000252488	9	4.51562E-16						
	9.95739E-07	ω	0						
U _{temp}	9.95739E-07		U						
Calibrated value	0.740500007			20	_				
Calibrated value	0.748500327		Effective degree of freedom	20					
standard uncertainty	0.00032665								
k factor	2.133028362								
K Idelei	2.100020002								
Extended uncertainty	0.000696753								
-			1						
		CALCULATION	OF LENGT	H CALIRI	RATIC	N			
		CHECCEMIIO	OI EENGII	ii Cribibi	MALI C) 1 (
	CTE [K-1]	Object of calibration Uncertainty of CTE (u _{aw}) [K ⁻¹]	(2 2) [IV2]		(T 2000	$C = (T_w - 20^{\circ}C)$			
ength of measurement [mm] 0.75	2.22E-05	0.00000069	$(u^2_{TW} + u^2_{TWS})[K^2]$ 0.003333333	u _{aM} 5.7735E-08	0.5	(1 _W - 20 C)			
0.70	L.EEC 00	0.0000000	0.0000000	0.77002.00	0.0				
-		Reference artefact used							
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
auge block	-	0.75	0.500000	0.000)1 2				
					_ ,				
Measurement repetition name	Calibration me	easurments: 4 positions, 5 repeatitions each Position 2	Position 3	Position 4	-	Measurements No.	Gauge block measuremen Position 1	Position 2	Position 3
-13	0.75000096	0.7500	0.7504	0.7503	1	1	0.5009	0.5009	0.500
-13	0.749900427	0.7501	0.7503	0.7503		2	0.5013	0.5013	0.501
-13	0.749200667	0.7494	0.7501	0.7506		3	0.5002	0.5002	0.500
-13	0.749900327	0.7496	0.7500	0.7502					
-13 Vi	0.75010024 0.749820524	0.7496 0.749740088	0.7498 0.750120163	0.7500 0.750280132	-				
y _i S _i	0.000356291	0.00029659	0.000238739	0.000216796					
(S _j)^2	1.26943E-07 -0.000169703	8.79655E-08 -0.000250139	5.69965E-08 0.000129936	4.70006E-08 0.000289905					
y _j - y (y _j - y)^2	2.8799E-08	6.25693E-08	1.68833E-08	8.40451E-08					
Coverage factor (p)	95.45	1%							
] ~							
у	0.749990227	J				E _{Lprop}	0.0016		
		Degree of freedom (v _e)	u_e^4/v_e						
U _{rep}	0.000282359] 16	1.58908E-17			L _{measstd}	0.5008		
U _{geo}	0.000126589	3	5.34983E-18			U _{measstd}	0.000482183	ree of freedom 8	
		1	5.5.500E-10			→ meassio	0.000 102 100	J	
EL	0.0012	J							
Ucorr	0.000252488	9	4.51562E-16						

0

		Object of calibration				7		
ength of measurement [mm]	CTE [K-1]	Uncertainty of CTE (uaW) [K-1]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	$u_{\alpha M}$	$(T_M - 20^\circ$	$^{\circ}C) = (T_{w} - 20^{\circ}C)$		
0.75	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5			
-						7		
Туре	Part number	Reference artefact used Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k	-		
auge block	-	0.7	5 0.500000	0.000	1 2	2		
-					_			
Measurement repetition name	Position 1	easurments: 4 positions, 5 repeatitions ea Position 2	Position 3	Position 4	-	Measurements No.	Gauge block measurement Position 1 Position 2	Position 3
3-19	0.7495	0.7503	0.7504	0.7488		1	0.5009 0.5009	0.5009
3-19 3-19	0.74980006 0.75010024	0.7503 0.7507	0.7502 0.7504	0.7492 0.7494		2 3	0.5013 0.5013 0.5002 0.5002	0.5013 0.5002
3-19	0.749900327	0.7500	0.7506	0.7493			0.5002 0.5002	0.5002
3-19	0.749700007	0.7505	0.7507	0.7506				
y _j S _j	0.749800127 0.000223723	0.750360008 0.000260761	0.750461169 0.000194579	0.749461053 0.000676555				
(S _j)^2	5.0052E-08	6.79961E-08	3.78608E-08	4.57727E-07				
y _j - y (y _i - y)^2	-0.000220462 4.86037E-08	0.000339419 1.15205E-07	0.00044058 1.9411E-07	-0.000559536 3.13081E-07				
			1.01112.01	0.100012 07				
Coverage factor (p)	95.45	1%						
у	0.750020589					E _{Lprop}	0.0016	
		Degree of freedom (ve)	u_e^4/v_e					
Urep	0.000391674	16	5.88357E-17			L _{measstd}	0.5008	
U _{geo}	0.000236467	3	6.5139E-17			U _{measstd}	Degree of freedom 0.000482183 8	
		-				- meassid		
EL	0.0012							
U _{corr}	0.000252488	9	4.51562E-16					
U _{temp}	9.95739E-07	∞	0					
			7					
Calibrated value	0.748820589		Effective degree of freedom	20				
standard uncertainty	0.00032926	1						
k factor	2.133028362							
Extended uncertainty	0.00070232							
		CALCULATION		. ~				
						- '		
	OTE IIII	Object of calibration	(2 . 2) pre2a			2000		
gth of measurement [mm] 0.75	CTE [K-1] 2.22E-05	Uncertainty of CTE (u _{aW}) [K ⁻¹] 0.00000069	$(u^2_{TW} + u^2_{TWS}) [K^2]$ 0.003333333	u _{aM} 5.7735E-08	$\frac{(1_{\rm M} - 20^{\circ} {\rm C})}{0.5}$	$= (T_w - 20^{\circ}C)$		
				311.1332.33				
-		Reference artefact used						
Type ige block	Part number	Nominal length /mm 0.75	Calibrated length /mm 0.500000	U calibration /mm 0.0001	k 2			
ige block		0.70	0.00000	0.0001	-			
	Calibration meas	surments: 4 positions, 5 repeatitions each			Г		Gauge block measurement	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4		Measurements No.	Position 1 Position 2 F	Position 3
25 25	0.750700666 0.75010054	0.7498 0.7490	0.7500 0.7501	0.7509 0.7504		1 2	0.5009 0.5009 0.5013 0.5013	0.5009 0.5013
25	0.749900167	0.7490	0.7504	0.7506		3	0.5002 0.5002	0.5002
25	0.74980006	0.7496	0.7502	0.7508				
25 V _i	0.75030054 0.750160394	0.7493 0.749340011	0.7499 0.750120792	0.7506 0.750660456				
y _i S _j	0.000358007	0.000357766	0.000192836	0.000195056				
(S _j)^2 y _j - y	1.28169E-07 8.99814E-05	1.27997E-07 -0.000730402	3.71856E-08 5.03786E-05	3.80467E-08 0.000590042				
(y _i - y)^2	8.09665E-09	5.33488E-07	2.53801E-09	3.4815E-07				
Coverage factor (p)	95.45 %	,						
у	0.750070413					E _{Lprop}	0.0016	
		D ()	4./					
U _{rep}	0.000287836	Degree of freedom (v _e) 16	u _e ⁴ / v _e 1.71601E-17			L _{measstd}	0.5008	
							Degree of freedom	
U _{geo}	0.000272683	3	1.15184E-16			U _{measstd}	0.000482183 8	
EL	0.0012							
U _{corr}								
	0.000252488	9	4.51562E-16					
U _{temo}		9	4.51562E-16 0					
U _{temp}	0.000252488 9.95739E-07							
U _{temp} Calibrated value				16				
Calibrated value	9.95739E-07 0.748870413		0	16				
	9.95739E-07 0.748870413 0.000314499		0	16				
Calibrated value	9.95739E-07 0.748870413		0	16				
Calibrated value standard uncertainty	9.95739E-07 0.748870413 0.000314499		0	16				

		Object of calibration]			
gth of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{αW}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS})[K^2]$	u _{aM}		$C) = (T_W - 20^{\circ}C)$			
0.75	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5	J			
-		Reference artefact used				1			
Type	Part number	Nominal length /mm 0.75	Calibrated length /mm 0.500000	U _{calibration /mm} 0.0001	k				
ige block	-	0.73	0.300000	0.0001		ı			
	Calibration mea	asurments: 4 positions, 5 repeatitions each			1		Gauge block meas	urement	
Measurement repetition name 31	Position 1 0.749400007	Position 2 0.7497	Position 3 0.7504	Position 4 0.7505	1	Measurements No.	Position 1 0.50	Position 2 09 0.5009	Position 3 0.5009
31	0.749700427	0.7501	0.7499	0.7510		2	0.50		0.5009
31	0.750000007	0.7502	0.7499	0.7503		3	0.50	0.5002	0.5002
31 31	0.750300007 0.749700107	0.7500 0.7503	0.7502 0.7504	0.7507 0.7507					
y _j S _j	0.749820111 0.000342007	0.750060048 0.000230189	0.750160237 0.000251192	0.750640152 0.000260679	1				
(S _j)^2	1.16969E-07	5.29868E-08	6.30974E-08	6.79535E-08					
y _j - y (y _i - y)^2	-0.000350026 1.22518E-07	-0.000110089 1.21196E-08	-9.89973E-06 9.80046E-11	0.000470015 2.20914E-07					
Coverage factor (p)	95.45	%			-				
		,				_	0.0040		
у	0.750170137					E _{Lprop}	0.0016		
	0.00007400	Degree of freedom (v _e)	u _e ⁴ /v _e				0.5000	_	
U _{rep}	0.00027432	16	1.4157E-17			Lmeasstd	0.5008	Degree of freedom	
u_{geo}	0.000172155	3	1.82996E-17			U _{measstd}	0.000482183	8	
EL	0.0012								
U _{corr}	0.000252488	9	4.51562E-16						
U _{temp}	9.95739E-07	60	0						
			· •						
Calibrated value	0.748970137		Effective degree of freedom	15]				
standard uncertainty	0.000293617								
-									
k factor	2.181165682								
Extended uncertainty	0.000640426								
		CALCULATION	OF LENGT	H CALIBI	KATI	ON			
gth of measurement [mm]	CTE [K-1]	Object of calibration Uncertainty of CTE $(u_{\alpha W})$ $[K^{-1}]$	$(u^2_{TW} + u^2_{TWS})[K^2]$	u_{aM}	$(T_M - 20)$	$T_{\rm W} = (T_{\rm W} - 20^{\circ}{\rm C})$			
0.75	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5				
						_			
Туре	Part number	Reference artefact used Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k	_			
ige block	-	0.75		0.000	1	2			
-					_				
Measurement repetition name	Position 1	asurments: 4 positions, 5 repeatitions each Position 2	Position 3	Position 4	-	Measurements No.	Gauge block me Position 1	Position 2	Position 3
2	0.750200107	0.7493	0.7495	0.7496		1		0.5009	0.500
2	0.7503 0.75	0.7495 0.7499	0.7502 0.7499	0.7499 0.7500		2 3		5013 0.5013 5002 0.5002	0.501 0.500
2	0.750200027	0.7491	0.7496	0.7496					
<u>V</u>	0.749800007 0.750100028	0.7497 0.749500147	0.7499 0.749820177	0.7495 0.749720156	-				
y _i S _i (S _i)^2	0.000200014 4.00057E-08	0.000316128 9.99366E-08	0.000277579 7.70501E-08	0.000216807 4.70052E-08					
y _i - y	0.000314901	-0.00028498	3.50503E-05	-6.4971E-05					
(y _j - y)^2	9.91626E-08	8.12137E-08	1.22852E-09	4.22123E-09					
Coverage factor (p)	95.45	%							
у	0.749785127					E _{Lprop}	0.0016		
		Degree of freedom (v _e)	u_e^4/ν_e						
U _{rep}	0.000256904	16	1.08898E-17			L _{measstd}	0.5008	□, ,, ,	
Ugeo	0.000124441	3	4.99585E-18			U _{measstd}	0.000482183	Degree of freedom	
EL	0.0012								
Ucorr	0.000252488	9	4.51562E-16						
U _{temp}	9.95739E-07	00	0						
Calibrated value	0.748585127		Effective degree of freedom	13	7				
			Lifective degree of freedom	13	_				
standard uncertainty	0.000284293								
k factor	2.211800697								
Extended uncertainty	0.000628798								
-			1						

		Object of calibration				1			
gth of measurement [mm]	CTE [K-1]	Uncertainty of CTE (uaW) [K-1]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	$u_{\alpha M}$	$(T_{M} - 20^{\circ})$	$T(C) = (T_w - 20^{\circ}C)$			
0.75	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5]			
		Reference artefact used]			
Type ige block	Part number	Nominal length /mm 0.75	Calibrated length /mm 0.500000	U _{calibration /mm} 0.0001	k	-			
ige block	-	0.73	0.500000	0.000	-	1			
	Calibration mo	asurments: 4 positions, 5 repeatitions each			7		Gauge block measurem	ont	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	1	Measurements No.	Position 1	Position 2	Position 3
18	0.749300027	0.7505	0.7499	0.7499		1	0.5009	0.5009	0.5009
18	0.749600007	0.7505	0.7495	0.7500		2	0.5013	0.5013	0.501
18 18	0.749300027 0.749400007	0.7508 0.7508	0.7496 0.7498	0.7494 0.7497		3	0.5002	0.5002	0.500
18	0.74920006	0.7505	0.7497	0.7496					
y _i S _i	0.749360025	0.750620145	0.74970082	0.749720666	1				
S _j (S _j)^2	0.000151639 2.29945E-08	0.000164245 2.69764E-08	0.000158003 2.4965E-08	0.000238732 5.6993E-08					
y _i - y	-0.000490389	0.000769731	-0.000149594	-0.000129749					
(y _i - y)^2	2.40481E-07	5.92486E-07	2.23783E-08	1.68347E-08					
Coverage factor (p)	95.45	%							
	0.749850414					-	0.0016		
у	0.749030414					E _{Lprop}	0.0016		
		Degree of freedom (v_e)	u_e^4/v_e						
U _{rep}	0.00018161	16	2.71957E-18			L _{measstd}	0.5008		
u_{geo}	0.000269595	3	1.10055E-16			U _{measstd}	0.000482183	egree of freedom 8	
	·					- meassid			
EL	0.0012								
U _{corr}	0.000252488	9	4.51562E-16						
	9.95739E-07	_	0						
U _{temp}	9.95/39E-0/	00	0						
]		_				
Calibrated value	0.748650414		Effective degree of freedom	13	_				
standard uncertainty	0.00029752								
	0.044000007								
k factor	2.211800697								
Extended uncertainty	0.000658054								
		CALCULATION	OF LENGTI	H CALIBR	ATI()N			
gth of measurement [mm]	CTE [K-1]	Object of calibration Uncertainty of CTE $(u_{\alpha W})$ $[K^{-1}]$	$(u^2_{TW} + u^2_{TWS}) [K^2]$	$\mathbf{u}_{a\mathrm{M}}$	(T _v = 20°0	$(T_{W} - 20^{\circ}C)$			
0.75	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5	-, (,			
		Reference artefact used							
Type ige block	Part number	Nominal length /mm 0.75	Calibrated length /mm 0.500000	U calibration /mm 0.0001	k 2				
ige block		0.70	0.00000	0.0001					
	Calibration mea	asurments: 4 positions, 5 repeatitions each			1 1		Gauge block measureme	nt	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4		Measurements No.	Position 1	Position 2	Position 3
24	0.7500015	0.7508	0.7509	0.7499		1	0.5009	0.5009	0.5009
24 24	0.750200007 0.75020024	0.7505 0.7499	0.7503 0.7503	0.7498 0.7501		2 3	0.5013 0.5002	0.5013 0.5002	0.5013 0.5002
24	0.749800107	0.7500	0.7502	0.7500		3	0.5002	0.5002	0.5002
24	0.749900107	0.7498	0.7505	0.7507					
y _j S _j	0.750020392 0.000178856	0.750200131 0.000430087	0.750440498 0.000279142	0.75010046 0.000353508					
(S _j)^2	3.19894E-08	1.84975E-07	7.79205E-08	1.24968E-07					
y _j - y	-0.000169978 2.88926E-08	5.70035L=00	0.000250128	-8.99103E-05					
(y _j - y)^2	•	9.52653E-11	6.25641E-08	8.08386E-09	l				
Coverage factor (p)	95.45	%							
у	0.75019037					E _{Lprop}	0.0016		
•	,	B 44 1 4 3	4.						
	0.00000000	Degree of freedom (v _e)	u _e ⁴ /v _e				0.5000		
u_{rep}	0.00032398	16	2.75432E-17			L _{measstd}	0.5008 De	gree of freedom	
U _{geo}	9.11207E-05	3	1.43624E-18			U _{measstd}	0.000482183	8	
EL	0.0012								
		_							
Ucorr	0.000252488	9	4.51562E-16						
U _{temp}	9.95739E-07	00	0						
Calibrated value	0.748990370		Effective degree of freedom	15	1				
standard uncertainty			Encoure degree or needen		1				
	0.000294651		Encours dogics of necousin						
k factor			Enouge degree of needen		1				
k factor Extended uncertainty	0.000294651		Castal degree of acceptance						

		Object of calibration							
gth of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{aw}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS})[K^2]$	$u_{\alpha M}$	(T _M – 20°C	$(T_W - 20^{\circ}C)$			
0.75	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5				
		Reference artefact used							
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
ige block	-	0.75	0.500000	0.000	01 2				
	Calibration me	easurments: 4 positions, 5 repeatitions each					Gauge block me	easurement	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4		Measurements No.	Position 1	Position 2	Position 3
30	0.749800027	0.7498	0.7496	0.7505		1		0.5009 0.500	
30 30	0.749600167 0.75020006	0.7499 0.7504	0.7501 0.7497	0.7503 0.7504		2 3		0.5013 0.50° 0.5002 0.500	
30	0.750300107	0.7502	0.7500	0.7498				7.5002 0.500	0.5002
30	0.750600167	0.7508	0.7500	0.7494					
y _j	0.750100105	0.750220101	0.749880233	0.750080077					
S _j (S _j)^2	0.000400012 1.6001E-07	0.000402493 1.62001E-07	0.000216862 4.7029E-08	0.000465815 2.16983E-07					
(3 ₁) 2 y ₁ - y	2.9976E-05	0.000149972		9.94801E-06					
y _i - y (y _i - y)^2	8.9856E-10	2.24916E-08	3.60605E-08	9.89628E-11					
Coverage factor (p)	95.45	1%							
oovolago laotol (p)									
у	0.750070129					E _{Lprop}	0.0016		
		Degree of freedom (v _e)	., 4 / .,						
Urep	0.000382761	16	u _e ⁴ / v _e 5.36598E-17			L _{measstd}	0.5008		
o-iop						meassto		Degree of freedo	m
Ugeo	7.04448E-05	3	5.13043E-19			U _{measstd}	0.000482183	8	
EL	0.0012								
L.									
U _{corr}	0.000252488	9	4.51562E-16						
H ₁	9.95739E-07		0						
U _{temp}	3.307 03E-07		v						
					_				
Calibrated value	0.748870129		Effective degree of freedom	17					
standard uncertainty	0.000307071	†							
otaniaa a anoortamity	0.000001011	I control of the cont							
k factor	2.158263401								
Extended uncertainty	0.000000744	1							
Extended uncertainty	0.000662741								
		•							
		CALCULATION	OF LENGTH	CALIBR	ATIO	N			
		CALCULATION	OF LENGTH	CALIBR	ATIO]	N			
		CALCULATION	OF LENGTH	CALIBR	ATIO	N			
		CALCULATION	OF LENGTH	CALIBR	ATIO	N			
		CALCULATION	OF LENGTH	CALIBR	ATIO	N			
] OF LENGTH	CALIBR	ATIO	N			
gth of measurement [mm]	CTE [K*]	CALCULATION Object of calibration Uncertainty of CTE $(u_{uw})[K^{-1}]$				N = (T _w - 20°C)			
gth of measurement [mm]	CTE [K ⁻¹] 2.22E-05	Object of calibration	OF LENGTH (u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333						
		Object of calibration $ \\ Uncertainty of CTE \left(u_{uw}\right)\left[K^{-1}\right] $	$(u^2_{TW} + u^2_{TWS}) [K^2]$	u _{aM}	(T _M - 20°C)				
		Object of calibration $ \\ Uncertainty of CTE \left(u_{uw}\right)\left[K^{-1}\right] $	$(u^2_{TW} + u^2_{TWS}) [K^2]$	u _{aM}	(T _M - 20°C)				
0.75 Type		Object of calibration $ \begin{array}{c} \text{Object of calibration} \\ \text{Uncertainty of CTE} \left(u_{aw}\right) \left[K^{-1}\right] \\ \text{0.00000069} \\ \\ \text{Reference artefact used} \\ \text{Nominal length } \textit{/mm} \end{array} $	$ \begin{array}{c} (u^2_{\mathrm{TW}} + u^2_{\mathrm{TWS}}) \left[K^2\right] \\ 0.003333333 \end{array} $ Calibrated length /mm	U _{nM} 5.7735E-08	(T _M - 20°C) 0.5				
0.75	2.22E-05	Object of calibration Uncertainty of CTE $(u_{uw})[K^{-1}]$ 0.00000069	$ \frac{\left(u^2_{TW} + u^2_{TWS}\right)\left[K^2\right]}{0.003333333} $	u _{oM} ((T _M – 20°C) 0.5				
0.75 Type	2.22E-05 Part number	Object of calibration Uncertainty of CTE (u _{sw}) [K ⁻¹] 0.0000069 Reference artefact used Nominal length /mm 0.75	$ \begin{array}{c} (u^2_{\mathrm{TW}} + u^2_{\mathrm{TWS}}) \left[K^2\right] \\ 0.003333333 \end{array} $ Calibrated length /mm	U _{nM} 5.7735E-08	(T _M - 20°C) 0.5				
0.75 Type ge block	2.22E-05 Part number Calibration mea	$\begin{array}{c} \text{Object of calibration} \\ \text{Uncertainty of CTE} \left(u_{wW}\right)\left[K^{-1}\right] \\ \text{0.00000069} \\ \\ \text{Reference artefact used} \\ \text{Nominal length /mm} \\ \text{0.75} \\ \\ \text{ssurments: 4 positions, 5 repeatitions each} \end{array}$	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 0.500000	U _{shM} 5.7735E-08	(T _M - 20°C) 0.5	= (T _w – 20°C)	Gauge block meas		Position 2
0.75 Type ge block Measurement repetition name	2.22E-05 Part number Calibration mea	Object of calibration Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 ssurments: 4 positions, 5 repeatitions each Position 2	(u² _{TW} + u² _{TWS}) [K²] 0.003333333	U _{sht} 5.7735E-08 U-satisfation from 0.0001	(T _M - 20°C) 0.5	$= (T_w - 20^{\circ}C)$ Measurements No.	Position 1	Position 2	Position 3
0.75 Type ge block	2.22E-05 Part number Calibration mea	$\begin{array}{c} \text{Object of calibration} \\ \text{Uncertainty of CTE} \left(u_{wW}\right)\left[K^{-1}\right] \\ \text{0.00000069} \\ \\ \text{Reference artefact used} \\ \text{Nominal length /mm} \\ \text{0.75} \\ \\ \text{ssurments: 4 positions, 5 repeatitions each} \end{array}$	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 0.500000	U _{shM} 5.7735E-08	(T _M - 20°C) 0.5	= (T _w – 20°C)		Position 2 09 0.5009	Position 3 0.5009 0.5013
0.75 Type ge block Measurement repetition name 36 36 36	2.22E-05 Part number Calibration mea Position 1 0.750500167 0.749900327 0.749800167	Object of calibration Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 ssurments: 4 positions, 5 repeatitions each Position 2 0.7493 0.7494 0.7494	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 0.500000 Position 3 0.7500 0.7497 0.7502	U _{shN} 5.7735E-08 U _{calibration inten} 0.0001 Position 4 0.7499 0.7499 0.7498	(T _M - 20°C) 0.5	$= (T_w - 20^{\circ}C)$ $= (T_w - 20^{\circ}C)$ Measurements No.	Position 1 0.50	Position 2 09 0.5009 13 0.5013	0.5009
0.75 Type ge block Measurement repetition name 66 66 66 66 66	2.22E-05 Part number Calibration mea Position 1 0.750500167 0.749900327 0.749800167 0.74950024	Object of calibration Uncertainty of CTE (u _{sw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions, 5 repeatitions each Position 2 0.7494 0.7494 0.7494	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 0.500000 Position 3 0.7500 0.7497 0.7502 0.7497	U _{salth-atton from} U _{calth-atton from} U _{calth-atton from} 0.0001 Position 4 0.7499 0.7499 0.7498 0.7504	(T _M - 20°C) 0.5	= (T _w – 20°C) Measurements No. 1 2	Position 1 0.50 0.50	Position 2 09 0.5009 13 0.5013	0.5009 0.5013
0.75 Type ge block Measurement repetition name 16 16 16 16 16	2.22E-05 Part number Calibration mea Position 1 0.750500167 0.749800167 0.749800167 0.74950024 0.74960054	Object of calibration Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 ssurments: 4 positions, 5 repeatitions each Position 2 0.7493 0.7494 0.7494 0.7495 0.7493	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 0.500000 Position 3 0.7500 0.7497 0.7502 0.7497 0.7496	U _{saltration from} U saltration from 0.0001 Position 4 0.7499 0.7499 0.7498 0.7504 0.7505	(T _M - 20°C) 0.5	= (T _w – 20°C) Measurements No. 1 2	Position 1 0.50 0.50	Position 2 09 0.5009 13 0.5013	0.5009 0.5013
0.75 Type ge block Measurement repetition name 16 16 16 16 16	2.22E-05 Part number Calibration mea Position 1 0.750500167 0.749900327 0.749800167 0.74950024	Object of calibration Uncertainty of CTE (u _{sw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions, 5 repeatitions each Position 2 0.7494 0.7494 0.7494	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 0.500000 Position 3 0.7500 0.7497 0.7502 0.7497	U _{salth-atton from} U _{calth-atton from} U _{calth-atton from} 0.0001 Position 4 0.7499 0.7499 0.7498 0.7504	(T _M - 20°C) 0.5	= (T _w – 20°C) Measurements No. 1 2	Position 1 0.50 0.50	Position 2 09 0.5009 13 0.5013	0.5009 0.5013
0.75 Type ge block Measurement repetition name 36 36 36 36 37 \$ \$ \$ \$ \$ \$ \$ \$ \$ \$ \$ \$ \$ \$ \$ \$ \$ \$	2.22E-05 Part number Calibration mea Position 1 0.750500167 0.749900327 0.749800167 0.74950024 0.74960054 0.749860288 0.000391077 1.52941E-07	Object of calibration Uncertainty of CTE (u _{sw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions. 5 repeatitions each Position 2 0.7493 0.7494 0.7494 0.7495 0.7493 0.749380185 8.39469E-05 7.04709E-09	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 0.500000 Position 3 0.7500 0.7497 0.7502 0.7497 0.7498 0.749840235 0.000250972 6.29872E-08	U _{subt} 5.7735E-08 U _{subtration from} 0.0001 Position 4 0.7499 0.7499 0.7498 0.7504 0.7505 0.750100085 0.000324012 1.0498E-07	(T _M - 20°C) 0.5	= (T _w – 20°C) Measurements No. 1 2	Position 1 0.50 0.50	Position 2 09 0.5009 13 0.5013	0.5009 0.5013
Type Type Ge block Measurement repetition name 66 66 7 S, (S,)*2 y, - y	2.22E-05 Part number Calibration mea Position 1 0.750500167 0.749900327 0.749800167 0.749960054 0.74960054 0.74960288 0.000391077 1.52941E-07 6.50897E-05	Object of calibration Uncertainty of CTE (u _{sw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 assuments: 4 positions. 5 repeatitions each Position 2 0.7493 0.7494 0.7494 0.7494 0.7495 0.7493 0.749380185 8.39469E-05 7.04709E-09 -0.000415013	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 0.500000 Position 3 0.7500 0.7497 0.7502 0.7497 0.7502 0.7498 0.749840235 0.000250972 6.29872E-08 4.50363E-05	U _{saltration hom} 5.7735E-08 U _{saltration hom} 0.0001 Position 4 0.7499 0.7499 0.7499 0.7504 0.7504 0.7505 0.000324012 1.04984E-07 0.000304887	(T _M - 20°C) 0.5	= (T _w – 20°C) Measurements No. 1 2	Position 1 0.50 0.50	Position 2 09 0.5009 13 0.5013	0.5009 0.5013
0.75 Type Ige block Measurement repetition name 166 166 167 168 179 189 189 189 189 189 189 18	2.22E-05 Part number Calibration mea Position 1 0.750500167 0.749900327 0.749900167 0.74990024 0.74996024 0.74960054 0.74960280 0.000391077 1.52941E-07 6.50897E-05 4.23667E-09	Object of calibration Uncertainty of CTE (u _{sw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions, 5 repeatitions each Position 2 0.7494 0.7494 0.7494 0.7494 0.7495 0.7493 0.749380185 8.39469E-05 7.04709E-09 -0.000415013 1.72236E-07	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 0.500000 Position 3 0.7500 0.7497 0.7502 0.7497 0.7498 0.749840235 0.000250972 6.29872E-08	U _{subt} 5.7735E-08 U _{subtration from} 0.0001 Position 4 0.7499 0.7499 0.7498 0.7504 0.7505 0.750100085 0.000324012 1.0498E-07	(T _M - 20°C) 0.5	= (T _w – 20°C) Measurements No. 1 2	Position 1 0.50 0.50	Position 2 09 0.5009 13 0.5013	0.5009 0.5013
Type Type Ge block Measurement repetition name 66 66 7 S, (S,)*2 y, - y	2.22E-05 Part number Calibration mea Position 1 0.750500167 0.749900327 0.749800167 0.749960054 0.74960054 0.74960288 0.000391077 1.52941E-07 6.50897E-05	Object of calibration Uncertainty of CTE (u _{sw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions, 5 repeatitions each Position 2 0.7494 0.7494 0.7494 0.7494 0.7495 0.7493 0.749380185 8.39469E-05 7.04709E-09 -0.000415013 1.72236E-07	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 0.500000 Position 3 0.7500 0.7497 0.7502 0.7497 0.7502 0.7498 0.749840235 0.000250972 6.29872E-08 4.50363E-05	U _{saltration hom} 5.7735E-08 U _{saltration hom} 0.0001 Position 4 0.7499 0.7499 0.7499 0.7504 0.7504 0.7505 0.000324012 1.04984E-07 0.000304887	(T _M - 20°C) 0.5	= (T _w – 20°C) Measurements No. 1 2	Position 1 0.50 0.50	Position 2 09 0.5009 13 0.5013	0.5009 0.5013
Type Type ge block Measurement repetition name 16 16 16 16 17 18 19 19 19 19 19 19 19 19 19	2.22E-05 Part number Calibration mea Position 1 0.750500167 0.749900327 0.749800167 0.74950024 0.74960028 0.00391077 1.52941E-07 6.50897E-05 4.23667E-09	Object of calibration Uncertainty of CTE (u _{sw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions, 5 repeatitions each Position 2 0.7494 0.7494 0.7494 0.7494 0.7495 0.7493 0.749380185 8.39469E-05 7.04709E-09 -0.000415013 1.72236E-07	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 0.500000 Position 3 0.7500 0.7497 0.7502 0.7497 0.7502 0.7498 0.749840235 0.000250972 6.29872E-08 4.50363E-05	U _{saltration hom} 5.7735E-08 U _{saltration hom} 0.0001 Position 4 0.7499 0.7499 0.7499 0.7504 0.7504 0.7505 0.000324012 1.04984E-07 0.000304887	(T _M - 20°C) 0.5	= (T _w - 20°C) Measurements No. 1 2 3	Position 1 0.50 0.50 0.50 0.50	Position 2 09 0.5009 13 0.5013	0.5009 0.5013
0.75 Type Ige block Measurement repetition name 166 166 167 168 179 189 189 189 189 189 189 18	2.22E-05 Part number Calibration mea Position 1 0.750500167 0.749900327 0.749900167 0.74990024 0.74996024 0.74960024 0.7496028 0.000391077 1.52941E-07 6.50897E-05 4.23667E-09	Object of calibration Uncertainty of CTE (u _{sw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions. 5 repeatitions each Position 2 0.7493 0.7494 0.7494 0.7495 0.7493 0.74945 0.7493 0.749380185 8.39469E-05 7.04709E-09 -0.000415013 1.72236E-07	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 0.500000 Position 3 0.7500 0.7497 0.7502 0.7497 0.7496 0.749840235 0.000250972 6.29872E-08 4.50363E-05 2.02827E-09	U _{saltration hom} 5.7735E-08 U _{saltration hom} 0.0001 Position 4 0.7499 0.7499 0.7499 0.7504 0.7504 0.7505 0.000324012 1.04984E-07 0.000304887	(T _M - 20°C) 0.5	= (T _w – 20°C) Measurements No. 1 2	Position 1 0.50 0.50	Position 2 09 0.5009 13 0.5013	0.5009 0.5013
0.75 Type Ige block Measurement repetition name 166 166 167 168 179 189 189 189 189 189 189 18	2.22E-05 Part number Calibration mea Position 1 0.750500167 0.749900327 0.749800167 0.74996024 0.74960024 0.74960024 0.7496028 0.000391077 1.52941E-07 6.50897E-05 4.23667E-09	Object of calibration Uncertainty of CTE (u _{sw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions, 5 repeatitions each Position 2 0.7493 0.7494 0.7494 0.7494 0.7494 0.7495 0.7493 1.749380185 8.39469E-05 7.04709E-09 -0.000415013 1.72236E-07	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 0.500000 Position 3 0.7500 0.7497 0.7502 0.7497 0.7496 0.749840235 0.000250972 6.29872E-08 4.50363E-05 2.02827E-09	U _{saltration hom} 5.7735E-08 U _{saltration hom} 0.0001 Position 4 0.7499 0.7499 0.7499 0.7504 0.7504 0.7505 0.000324012 1.04984E-07 0.000304887	(T _M - 20°C) 0.5	$= (T_w - 20^{\circ}C)$ $= (T_w - 20^{\circ}C)$ $= \frac{1}{2}$ $= \frac{2}{3}$ $= \frac{1}{3}$ $= \frac{1}{2}$	Position 1 0.50 0.50 0.50	Position 2 09 0.5009 13 0.5013	0.5009 0.5013
Type Type ge block Measurement repetition name 16 16 16 16 17 18 19 19 19 19 19 19 19 19 19	2.22E-05 Part number Calibration mea Position 1 0.750500167 0.749900327 0.749800167 0.74950024 0.74960028 0.00391077 1.52941E-07 6.50897E-05 4.23667E-09	Object of calibration Uncertainty of CTE (u _{sw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions. 5 repeatitions each Position 2 0.7493 0.7494 0.7494 0.7495 0.7493 0.74945 0.7493 0.749380185 8.39469E-05 7.04709E-09 -0.000415013 1.72236E-07	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 0.500000 Position 3 0.7500 0.7497 0.7502 0.7497 0.7496 0.749840235 0.000250972 6.29872E-08 4.50363E-05 2.02827E-09	U _{saltration hom} 5.7735E-08 U _{saltration hom} 0.0001 Position 4 0.7499 0.7499 0.7499 0.7504 0.7504 0.7505 0.000324012 1.04984E-07 0.000304887	(T _M - 20°C) 0.5	= (T _w - 20°C) Measurements No. 1 2 3	Position 1 0.50 0.50 0.50 0.50	Position 2 0 0.5009 13 0.5013 0.5013 0.5002	0.5009 0.5013
Type Type In the second of t	2.22E-05 Part number Calibration mea Position 1 0.750500167 0.749900327 0.749800167 0.74996024 0.74960024 0.74960024 0.7496028 0.000391077 1.52941E-07 6.50897E-05 4.23667E-09	Object of calibration Uncertainty of CTE (u _{sw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions, 5 repeatitions each Position 2 0.7493 0.7494 0.7494 0.7494 0.7494 0.7495 0.7493 1.749380185 8.39469E-05 7.04709E-09 -0.000415013 1.72236E-07	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 0.500000 Position 3 0.7500 0.7497 0.7502 0.7497 0.7496 0.749840235 0.000250972 6.29872E-08 4.50363E-05 2.02827E-09	U _{saltration hom} 5.7735E-08 U _{saltration hom} 0.0001 Position 4 0.7499 0.7499 0.7499 0.7504 0.7504 0.7505 0.000324012 1.04984E-07 0.000304887	(T _M - 20°C) 0.5	$= (T_w - 20^{\circ}C)$ $= (T_w - 20^{\circ}C)$ $= \frac{1}{2}$ $= \frac{2}{3}$ $= \frac{1}{3}$ $= \frac{1}{2}$	Position 1 0.50 0.50 0.50	Position 2 09 0.5009 13 0.5013	0.5009 0.5013
Type Type In the second of t	2.22E-05 Part number Calibration mea Position 1 0.750500167 0.749900327 0.749800167 0.74950024 0.74960028 0.000391077 1.52941E-07 4.23667E-09 95.45] 0.749795198	Object of calibration Uncertainty of CTE (u _{sw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 0.7493 0.7494 0.7494 0.7495 0.7493 0.74938 3.9469E-05 7.04709E-09 -0.000415013 1.72236E-07 % Degree of freedom (v _c)	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 0.500000 Position 3 0.7500 0.7497 0.7502 0.7497 0.7502 0.7498 0.749840235 0.000250972 6.29872E-08 4.50363E-05 2.02827E-09	U _{saltration hom} 5.7735E-08 U _{saltration hom} 0.0001 Position 4 0.7499 0.7499 0.7499 0.7504 0.7504 0.7505 0.000324012 1.04984E-07 0.000304887	(T _M - 20°C) 0.5	$= (T_W - 20^{\circ}C)$ $= (T_W - 20^{\circ}C)$ $= \frac{1}{2}$ $= \frac{1}{3}$ $= \frac{1}{3}$ $= \frac{1}{2}$ $= \frac{1}{3}$ $= \frac{1}{2}$ $= \frac{1}{3}$	Position 1 0.50 0.50 0.50 0.50 0.50	Position 2 0.5009 0.5009 13 0.5013 02 0.5002 0.5002 0.5002	0.5009 0.5013
Type Type In the second of t	2.22E-05 Part number Calibration mea Position 1 0.750500167 0.749900327 0.749900167 0.74950024 0.74950024 0.74960028 0.000391077 1.52941E-07 6.50897E-05 4.23667E-09 95.45]	Object of calibration Uncertainty of CTE (u _{sw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 0.7493 0.7494 0.7494 0.7495 0.7493 0.74938 3.9469E-05 7.04709E-09 -0.000415013 1.72236E-07 % Degree of freedom (v _c)	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 0.500000 Position 3 0.7500 0.7497 0.7502 0.7497 0.7502 0.7498 0.749840235 0.000250972 6.29872E-08 4.50363E-05 2.02827E-09	U _{saltration hom} 5.7735E-08 U _{saltration hom} 0.0001 Position 4 0.7499 0.7499 0.7499 0.7504 0.7504 0.7505 0.000324012 1.04984E-07 0.000304887	(T _M - 20°C) 0.5	$= (T_W - 20^{\circ}C)$ $= (T_W - 20^{\circ}C)$ $= \frac{1}{2}$ $= \frac{1}{3}$ $= \frac{1}{3}$ $= \frac{1}{2}$ $= \frac{1}{3}$ $= \frac{1}{2}$ $= \frac{1}{3}$	Position 1 0.50 0.50 0.50 0.50 0.50	Position 2 0.5009 0.5009 13 0.5013 02 0.5002 0.5002 0.5002	0.5009 0.5013
Type Type In the second of t	2.22E-05 Part number Calibration mea Position 1 0.750500167 0.749900327 0.749800167 0.74950024 0.74960028 0.000391077 1.52941E-07 4.23667E-09 95.45] 0.749795198	Object of calibration Uncertainty of CTE (u _{sw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 0.7493 0.7494 0.7494 0.7495 0.7493 0.74938 3.9469E-05 7.04709E-09 -0.000415013 1.72236E-07 % Degree of freedom (v _c)	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 0.500000 Position 3 0.7500 0.7497 0.7502 0.7497 0.7502 0.7498 0.749840235 0.000250972 6.29872E-08 4.50363E-05 2.02827E-09	U _{saltration hom} 5.7735E-08 U _{saltration hom} 0.0001 Position 4 0.7499 0.7499 0.7499 0.7504 0.7504 0.7505 0.000324012 1.04984E-07 0.000304887	(T _M - 20°C) 0.5	$= (T_W - 20^{\circ}C)$ $= (T_W - 20^{\circ}C)$ $= \frac{1}{2}$ $= \frac{1}{3}$ $= \frac{1}{3}$ $= \frac{1}{2}$ $= \frac{1}{3}$ $= \frac{1}{2}$	Position 1 0.50 0.50 0.50 0.50 0.50	Position 2 0.5009 0.5009 13 0.5013 02 0.5002 0.5002 0.5002	0.5009 0.5013
Type Type Ige block Measurement repetition name Ige block Measurement repetition name Ige block Ige blo	2.22E-05 Part number Calibration mea Position 1 0.750500167 0.749900327 0.749800167 0.749900327 0.749860054 0.74986054 0.000391077 1.52941E-07 6.50897E-05 4.23667E-09 95.45] 0.749795198 0.000286339 0.000150404 0.0012	Object of calibration Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions, 5 repeatitions each Position 2 0.7493 0.7494 0.7494 0.7495 0.7493 0.749380185 8.39469E-05 7.04709E-09 -0.000415013 1.72236E-07 % Degree of freedom (v _e) 16 3	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 0.500000 Position 3 0.7500 0.7497 0.7502 0.7497 0.7496 0.7498-0.00250972 6.29872E-08 4.50363E-05 2.02827E-09 u _e ⁴ /v _e 1.68059E-17 1.0661E-17	U _{saltration hom} 5.7735E-08 U _{saltration hom} 0.0001 Position 4 0.7499 0.7499 0.7499 0.7504 0.7504 0.7505 0.000324012 1.04984E-07 0.000304887	(T _M - 20°C) 0.5	$= (T_W - 20^{\circ}C)$ $= (T_W - 20^{\circ}C)$ $= \frac{1}{2}$ $= \frac{1}{3}$ $= \frac{1}{3}$ $= \frac{1}{2}$ $= \frac{1}{3}$ $= \frac{1}{2}$	Position 1 0.50 0.50 0.50 0.50 0.50	Position 2 0.5009 0.5009 13 0.5013 02 0.5002 0.5002 0.5002	0.5009 0.5013
Type Type ge block Measurement repetition name 16 16 16 16 17 18 19 19 19 19 19 19 19 19 19	2.22E-05 Part number Calibration mea Position 1 0.750500167 0.74950024 0.749800167 0.74950024 0.74960028 0.74960028 0.74960028 0.7496028 0.000391077 1.52941E-07 6.50897E-05 4.23667E-09 95.45] 0.749795198 0.000286339 0.000150404	Object of calibration Uncertainty of CTE (u _{sw}) [K-¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions, 5 repeatitions each Position 2 0.7493 0.7494 0.7494 0.7495 0.7493 0.749380185 8.39469E-05 7.04709E-09 -0.000415013 1.72236E-07	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 0.500000 Position 3 0.7500 0.7497 0.7502 0.7497 0.7496 0.749840235 0.000250972 6.29872E-08 4.50363E-05 2.02827E-09	U _{saltration hom} 5.7735E-08 U _{saltration hom} 0.0001 Position 4 0.7499 0.7499 0.7499 0.7504 0.7504 0.7505 0.000324012 1.04984E-07 0.000304887	(T _M - 20°C) 0.5	$= (T_W - 20^{\circ}C)$ $= (T_W - 20^{\circ}C)$ $= \frac{1}{2}$ $= \frac{1}{3}$ $= \frac{1}{3}$ $= \frac{1}{2}$ $= \frac{1}{3}$ $= \frac{1}{2}$	Position 1 0.50 0.50 0.50 0.50 0.50	Position 2 0.5009 0.5009 13 0.5013 02 0.5002 0.5002 0.5002	0.5009 0.5013
Type Type In the second of t	2.22E-05 Part number Calibration mea Position 1 0.750500167 0.749900327 0.749900327 0.74990054 0.74950024 0.74960028 0.000391077 1.52941E-07 6.50897E-05 4.23667E-09 95.45] 0.749795198 0.000286339 0.000150404 0.0012 0.000252488 9.95739E-07	Object of calibration Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions, 5 repeatitions each Position 2 0.7493 0.7494 0.7494 0.7495 0.7493 0.749380185 8.39469E-05 7.04709E-09 -0.000415013 1.72236E-07 % Degree of freedom (v _e) 16 3	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 0.500000 Position 3 0.7500 0.7497 0.7502 0.7497 0.7502 0.7498 0.7498 0.7498-0.00250972 6.29872E-08 4.50363E-05 2.02827E-09 u _e ⁴ / v _e 1.68059E-17 1.0661E-17 4.51562E-16	U _{saltration from} 5.7735E-08 U _{saltration from} 0.0001 Position 4 0.7499 0.7499 0.7499 0.7504 0.7505 0.750100085 0.000324012 1.04984E-07 0.000304887 9.2956E-08	(T _M - 20°C) 0.5	$= (T_W - 20^{\circ}C)$ $= (T_W - 20^{\circ}C)$ $= \frac{1}{2}$ $= \frac{1}{3}$ $= \frac{1}{3}$ $= \frac{1}{2}$ $= \frac{1}{3}$ $= \frac{1}{2}$	Position 1 0.50 0.50 0.50 0.50 0.50	Position 2 0.5009 0.5009 13 0.5013 02 0.5002 0.5002 0.5002	0.5009 0.5013
Type Type Ige block Measurement repetition name Ige block Measurement repetition name Ige block Ige blo	2.22E-05 Part number Calibration mea Position 1 0.750500167 0.749900327 0.749800167 0.749900327 0.749860054 0.74986054 0.000391077 1.52941E-07 6.50897E-05 4.23667E-09 95.45] 0.749795198 0.000286339 0.000150404 0.0012	Object of calibration Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions, 5 repeatitions each Position 2 0.7493 0.7494 0.7494 0.7495 0.7493 0.749380185 8.39469E-05 7.04709E-09 -0.000415013 1.72236E-07 % Degree of freedom (v _e) 16 3	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 0.500000 Position 3 0.7500 0.7497 0.7502 0.7497 0.7496 0.7498-0.00250972 6.29872E-08 4.50363E-05 2.02827E-09 u _e ⁴ /v _e 1.68059E-17 1.0661E-17	U _{saltration hom} 5.7735E-08 U _{saltration hom} 0.0001 Position 4 0.7499 0.7499 0.7499 0.7504 0.7504 0.7505 0.000324012 1.04984E-07 0.000304887	(T _M - 20°C) 0.5	$= (T_W - 20^{\circ}C)$ $= (T_W - 20^{\circ}C)$ $= \frac{1}{2}$ $= \frac{1}{3}$ $= \frac{1}{3}$ $= \frac{1}{2}$ $= \frac{1}{3}$ $= \frac{1}{2}$	Position 1 0.50 0.50 0.50 0.50 0.50	Position 2 0.5009 0.5009 13 0.5013 02 0.5002 0.5002 0.5002	0.5009 0.5013
Type Type In the second of t	2.22E-05 Part number Calibration mea Position 1 0.750500167 0.749900327 0.749800167 0.74996028 0.74960024 0.74960028 0.000391077 1.52941E-07 4.23667E-09 95.45] 0.749795198 0.000286339 0.000150404 0.0012 0.000252488 9.95739E-07	Object of calibration Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions, 5 repeatitions each Position 2 0.7493 0.7494 0.7494 0.7495 0.7493 0.749380185 8.39469E-05 7.04709E-09 -0.000415013 1.72236E-07 % Degree of freedom (v _e) 16 3	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 0.500000 Position 3 0.7500 0.7497 0.7502 0.7497 0.7502 0.7498 0.7498 0.7498-0.00250972 6.29872E-08 4.50363E-05 2.02827E-09 u _e ⁴ / v _e 1.68059E-17 1.0661E-17 4.51562E-16	U _{saltration from} 5.7735E-08 U _{saltration from} 0.0001 Position 4 0.7499 0.7499 0.7499 0.7504 0.7505 0.750100085 0.000324012 1.04984E-07 0.000304887 9.2956E-08	(T _M - 20°C) 0.5	$= (T_W - 20^{\circ}C)$ $= (T_W - 20^{\circ}C)$ $= \frac{1}{2}$ $= \frac{1}{3}$ $= \frac{1}{3}$ $= \frac{1}{2}$ $= \frac{1}{3}$ $= \frac{1}{2}$	Position 1 0.50 0.50 0.50 0.50 0.50	Position 2 0.5009 0.5009 13 0.5013 02 0.5002 0.5002 0.5002	0.5009 0.5013
Type Type In the second of t	2.22E-05 Part number Calibration mea Position 1 0.750500167 0.749900327 0.749900327 0.74990054 0.74950024 0.74960028 0.000391077 1.52941E-07 6.50897E-05 4.23667E-09 95.45] 0.749795198 0.000286339 0.000150404 0.0012 0.000252488 9.95739E-07	Object of calibration Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions, 5 repeatitions each Position 2 0.7493 0.7494 0.7494 0.7495 0.7493 0.749380185 8.39469E-05 7.04709E-09 -0.000415013 1.72236E-07 % Degree of freedom (v _e) 16 3	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 0.500000 Position 3 0.7500 0.7497 0.7502 0.7497 0.7502 0.7498 0.7498 0.7498-0.00250972 6.29872E-08 4.50363E-05 2.02827E-09 u _e ⁴ / v _e 1.68059E-17 1.0661E-17 4.51562E-16	U _{saltration from} 5.7735E-08 U _{saltration from} 0.0001 Position 4 0.7499 0.7499 0.7499 0.7504 0.7505 0.750100085 0.000324012 1.04984E-07 0.000304887 9.2956E-08	(T _M - 20°C) 0.5	$= (T_W - 20^{\circ}C)$ $= (T_W - 20^{\circ}C)$ $= \frac{1}{2}$ $= \frac{1}{3}$ $= \frac{1}{3}$ $= \frac{1}{2}$ $= \frac{1}{3}$ $= \frac{1}{2}$	Position 1 0.50 0.50 0.50 0.50 0.50	Position 2 0.5009 0.5009 13 0.5013 02 0.5002 0.5002 0.5002	0.5009 0.5013

Calibrated value

standard uncertainty

k factor

Extended uncertainty

CALCULATION OF LENGTH CALIBRATION

		Object of calibration							
ength of measurement [mm]	CTE [K-1]	Uncertainty of CTE (uaW) [K-1]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	$u_{\alpha M}$		$T(C) = (T_W - 20^{\circ}C)$			
0.75	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5				
Туре	Part number	Reference artefact used Nominal length /mm	Calibrated length /mm	U calibration /mm	k				
auge block	-	0.75		0.0001					
		asurments: 4 positions, 5 repeatitions each] [Gauge block measurer	nent	
Measurement repetition name	Position 1 1.060165218	Position 2 1.0597	Position 3 1.0593	Position 4 1.0609	-	Measurements No.	Position 1	Position 2	Position 3
-8 -8	1.060023797	1.0592	1.0590	1.0610		2	0.5009 0.5013	0.5009 0.5013	0.5009 0.5013
-8	1.059741124	1.0602	1.0589	1.0605		3	0.5002	0.5002	0.5002
-8	1.059811653	1.0600	1.0588	1.0608					
-8 V	1.060165218 1.059981402	1.0600 1.05982581	1.0594 1.059076354	1.0607 1.060787824	-				
y _i S _j	0.000197435	0.000372147	0.000257964	0.000183129					
(S _j)^2	3.89806E-08 6.35548E-05	1.38493E-07 -9.20375E-05	6.65452E-08 -0.000841494	3.35361E-08 0.000869976					
y _i - y (y _i - y)^2	4.03921E-09	-9.20375E-05 8.4709E-09	7.08112E-07	7.56859E-07					
	05.451	0/			-				
Coverage factor (p)	95.45	76							
у	1.059917847					E _{Lprop}	0.0016		
		Degree of freedom (ve)	u_e^4/v_e						
U _{rep}	0.000263418	16	1.2037E-17			L _{measstd}	0.5008		
						-11003300		Degree of freedom	
u_{geo}	0.000350889	3	3.1582E-16			U _{measstd}	0.000482183	8	
E∟	0.0012								
	0.000252488	9	4.51562E-16						
Ucorr		9							
U _{temp}	9.95739E-07	00	0						
Calibrated value	1.058717847		Effective degree of freedom	15					
standard uncertainty	0.000329256								
standard uncertainty	0.000023230								
k factor	2.181165682								
Extended uncertainty	0.000718162								

			_						
		CALCULATION	OF LENGTH	H CALIBR	ATIO	N			
ength of measurement [mm]	CTE [K-1]	Object of calibration	$(n^2 + n^2)[V^2]$	/	(T 20°C)	- (T 20°C)			
0.75	2.22E-05	Uncertainty of CTE (u _{aW}) [K ⁻¹] 0.00000069	$(u^2_{TW} + u^2_{TWS}) [K^2]$ 0.003333333	u _{aM} (5.7735E-08	$\frac{(1_{\rm M} - 20^{\circ} {\rm C})}{0.5}$	$= (T_w - 20^{\circ}C)$			
			33333333	311.1032.30					
		Reference artefact used							
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
auge block	-	0.75	0.500000	0.0001	2				
					_				
Measurement repetition name	Calibration mea	surments: 4 positions, 5 repeatitions each Position 2	Position 3	Position 4	_	Measurements No.	Gauge block measureme Position 1	Position 2	Position 3
-15	1.060660172	1.0621	1.0600	1.0599	-	1	0.5009	0.5009	0.5009
-15	1.05967026	1.0621	1.0604	1.0595		2	0.5013	0.5013	0.5013
-15	1.060306677	1.0619	1.0602	1.0597		3	0.5002	0.5002	0.5002
-15 -15	1.060448155 1.060306621	1.0622 1.0621	1.0601 1.0607	1.0596 1.0595					
Уј	1.060278377	1.062074415	1.060264204	1.059629017					
S _j (S _i)^2	0.000369458 1.36499E-07	0.000132244 1.74885E-08	0.00030249 9.15003E-08	0.000162884 2.65313E-08					
	-0.000283126	0.001512911		-0.000932487					
y _i - y (y _i - y)^2	8.01604E-08	2.2889E-06	8.83866E-08	8.69531E-07					
Coverage factor (p)	95.45	%							
						-	0.0012		
у	1.060561503					E _{Lprop}	0.0016		
		Degree of freedom (ve)	u_e^4/ν_e						
u _{rep}	0.000260777	16	1.15616E-17			L _{measstd}	0.5008		
U _{geo}	0.000526544	3	1.60139E-15			U _{measstd}	0.000482183	egree of freedom 8	
			== .=						
EL	0.0012								
U _{corr}	0.000252488	9	4.51562E-16						
II	9.95739E-07	∞	0						

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		Object of collegation							
Length of measurement [mm]	CTE [K-1]	Object of calibration Uncertainty of CTE (u _{aw}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	11	(T = 20°C	$(T_{W} - 20^{\circ}C)$			
0.75	2.22E-05	0.00000069	0.003333333	u _{aM} 5.7735E-08	0.5	(1 _W - 20 C)			
				***************************************	1				
		Reference artefact used							
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
Gauge block	-	0.75	0.500000	0.000	1 2				
		surments: 4 positions, 5 repeatitions each]		Gauge block measurement		
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	4	Measurements No.			Position 3
15-22 15-22	1.060801631 1.061862369	1.0591 1.0597	1.0613 1.0613	1.0612 1.0617		1 2	0.5009 0.5013	0.5009 0.5013	0.50
15-22	1.061650159	1.0594	1.0612	1.0615		3	0.5002	0.5002	0.5
15-22	1.06143801	1.0585	1.0617	1.0617	'		-		
15-22	1.061013841	1.0592	1.0612	1.0619					
y _i S _i	1.061353202 0.000439893	1.059175295 0.000447232	1.061339 0.000221359	1.061565362 0.000261808					
(S _j)^2	1.93506E-07	2.00016E-07	4.89997E-08	6.85434E-08					
y _j - y	0.000494987	-0.001002313	0.000400700	0.000707147					
(y _j - y)^2	2.45012E-07	2.83222E-06	2.31154E-07	5.00057E-07					
Coverage factor (p)	95.45 %	6							
	1.060858215					_	0.0046		
у	1.000636213					E _{Lprop}	0.0016		
		Degree of freedom (ve)	u_e^4/v_e						
U _{rep}	0.000357444	16	4.08106E-17			L _{measstd}	0.5008		
	0.000563356	3	2.09841E-15			ш	0.000482183	e of freedom 8	
U _{geo}		ű	2.000412-10			• measstd	0.000402100	O .	
EL	0.0012								
Ucorr	0.000252488	9	4.51562E-16						
Con		ű							
U _{temp}	9.95739E-07	00	0						
			1						
Calibrated value	1.059658215		Effective degree of freedom	10	7				
					_				
standard uncertainty	0.000410666								
k factor	2.283681613								
Extended uncertainty	0.000937831								
		CALCULATION		. ~					
		Object of calibration							
Length of measurement [mm]	CTE [K ^{-†}]	Object of calibration Uncertainty of CTE $(u_{aw})(K^{-1})$	$(u_{TW}^2 + u_{TWS}^2) [K^2]$	U _{oM}	(T _M – 20°C	$(T_{\rm W} - 20^{\circ}{\rm C})$			
Length of measurement [mm]	CTE [K ⁻¹] 2.22E-05	Object of calibration Uncertainty of CTE (u_{aw}) [K ⁻¹] 0.0000069	$(u^{2}_{TW} + u^{2}_{TWS}) [K^{2}]$ 0.003333333	u _{oM} 5.7735E-08	$(T_{\rm M} - 20^{\circ}{\rm C})$	$(C) = (T_w - 20^{\circ}C)$			
		Uncertainty of CTE (uaW) [K-1]				$C = (T_W - 20^{\circ}C)$			
		Uncertainty of CTE (uaW) [K-1]				$(T_{w} - 20^{\circ}C)$			
0.75 Type		Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm	0.003333333 Calibrated length /mm	5.7735E-08 U calibration /mm	0.5	$(T_{\rm W} - 20^{\circ}{\rm C})$			
0.75	2.22E-05	Uncertainty of CTE (u _{eW}) [K ⁻¹] 0.00000069 Reference artefact used	0.003333333 Calibrated length /mm	5.7735E-08	0.5	$(T_{\rm w} - 20^{\circ}{\rm C})$			
0.75 Type	2.22E-05 Part number	Uncertainty of CTE (u_{aw}) $[K^{-1}]$ 0.00000069 Reference artefact used Nominal length /mm 0.75	0.003333333 Calibrated length /mm 0.500000	5.7735E-08 U calibration /mm	0.5	$(T_{\rm w} - 20^{\circ}{\rm C})$			
0.75 Type Gauge block	2.22E-05 Part number - Calibration mea	Uncertainty of CTE (u_{aW}) $[K^{-1}]$ 0.00000069 Reference artefact used Nominal length /mm 0.75	0.003333333 Calibrated length /mm 0.500000	5.7735E-08 Ucalibration /mm 0.0001	0.5		Gauge block measurement Position 1 Po	ssition 2	Position 3
0.75 Type Gauge block Measurement repetition name	2.22E-05 Part number - Calibration meat Position 1	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 surments: 4 positions, 5 repeatitions each Position 2	0.003333333 Calibrated length /mm 0.500000 Position 3	5.7735E-08 Ucalibration Imm 0.0001 Position 4	0.5	$(C) = (T_W - 20^{\circ}C)$ Measurements No.	Position 1 Po		Position 3
0.75 Type Gauge block	2.22E-05 Part number - Calibration mea: Position 1 1.05982357 1.05952881	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 surments: 4 positions, 5 repeatitions each Position 2 1.0627 1.0626	0.003333333 Calibrated length /mm 0.500000	5.7735E-08 U cultivation imm 0.0001 Position 4 1.0591 1.0590	0.5			sition 2 0.5009 0.5013	Position 3 0.50 0.50 0.50
0.75 Type Gauge block Measurement repetition name 22-29 22-29 22-29	2.22E-05 Part number - Calibration meat Position 1 1.059882357 1.05952881 1.05938738	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 surments: 4 positions, 5 repeatitions each Position 2 1.0627 1.0626 1.0626	0.003333333 Calibrated length /mm 0.500000 Position 3 1.0612 1.0614 1.0616	5.7735E-08 U_altitudon /mm 0.0001 Position 4 1.0591 1.0590 1.0592	0.5	Measurements No.	Position 1 Po 0.5009	0.5009	0.50
0.75 Type Gauge block Measurement repetition name 22-29 22-29 22-29 22-29 22-29	2.22E-05 Part number Calibration mea: Position 1 1.059882357 1.0593881 1.05938738 1.05938738	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 surments: 4 positions, 5 repeatitions each Position 2 1.0627 1.0626 1.0626 1.0630	0.003333333 Calibrated length /mm 0.500000 Position 3 1.0612 1.0614 1.0616 1.0608	5.7735E-08 U calibration /mm 0.0001 Position 4 1.0591 1.0592 1.0592	0.5	Measurements No. 1 2	Position 1 Po 0.5009 0.5013	0.5009 0.5013	0.50 0.50
0.75 Type Gauge block Measurement repetition name 22-29 22-29 22-29 22-29 22-29 22-29 22-29	2.22E-05 Part number Calibration meat Position 1 1.05982357 1.05938738 1.05938738 1.059811729	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 surments: 4 positions, 5 repeatitions each Position 2 1.0627 1.0626 1.0626 1.0626 1.0626	0.003333333 Calibrated length /mm 0.500000 Position 3 1.0612 1.0614 1.0616 1.0608 1.0614	U cultiration imm 0.0001 Position 4 1.0591 1.0590 1.0592 1.0592 1.0595	0.5	Measurements No. 1 2	Position 1 Po 0.5009 0.5013	0.5009 0.5013	0.50 0.50
0.75 Type Gauge block Measurement repetition name 22-29 22-29 22-29 22-29 22-29 22-29 22-29 31, S,	2.22E-05 Part number - Calibration mea: Position 1 1.05982357 1.05952881 1.05938738 1.05938738 1.05938738 1.059811729 1.059599531 0.00023454	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 surments: 4 positions, 5 repeatitions each Position 2 1.0627 1.0626 1.0626 1.0626 1.0626 1.06266 0.000176222	0.003333333 Calibrated length /mm 0.500000 Position 3 1.0612 1.0614 1.0616 1.0608 1.0614 1.06182474 0.000297467	5.7735E-08 U_calibration invm 0.0001 Position 4 1.0591 1.0590 1.0592 1.0592 1.0592 1.0592 0.000209743	0.5	Measurements No. 1 2	Position 1 Po 0.5009 0.5013	0.5009 0.5013	0.50 0.50
0.75 Type Gauge block Measurement repetition name 22-29 22-29 22-29 22-29 22-29 22-29 (S)(S)(Y)2	2.22E-05 Part number - Calibration meat Position 1 1.059882357 1.05952881 1.05938738 1.059811729 1.059599531 0.00023454 5.5009E-08	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 surments: 4 positions, 5 repeatitions each Position 2 1.0627 1.0626 1.0626 1.0630 1.0626 1.062696861 0.000176222 3.10541E-08	Calibrated length /mm 0.500000 Position 3 1.0612 1.0614 1.0616 1.0608 1.0614 1.061282474 0.000297467 8.84865E-08	5.7735E-08 U_astitution imm 0.0001 Position 4 1.0591 1.0590 1.0592 1.0592 1.0595 1.059203572 0.000209743 4.39922E-08	0.5	Measurements No. 1 2	Position 1 Po 0.5009 0.5013	0.5009 0.5013	0.50 0.50
0.75 Type Gauge block Measurement repetition name 22-29 22-29 22-29 22-29 22-29 22-29 22-29 31, S,	2.22E-05 Part number - Calibration mea: Position 1 1.05982357 1.05952881 1.05938738 1.05938738 1.05938738 1.059811729 1.059599531 0.00023454	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 surments: 4 positions, 5 repeatitions each Position 2 1.0627 1.0626 1.0626 1.0626 1.0626 1.06266 0.000176222	Calibrated length /mm 0.500000 Position 3 1.0612 1.0614 1.0616 1.0608 1.0614 1.061282474 0.000297467 8.84865E-08	5.7735E-08 U additionation imm 0.0001 Position 4 1.0591 1.0590 1.0592 1.0592 1.0595 1.059203572 0.000209743 4.39922E-08	0.5	Measurements No. 1 2	Position 1 Po 0.5009 0.5013	0.5009 0.5013	0.50 0.50
0.75 Type Gauge block Measurement repetition name 22-29 22-29 22-29 22-29 22-29 22-29 y _i (S _i)'22 y _i - y' y'	2.22E-05 Part number Calibration mea: Position 1 1.05988.2357 1.05952881 1.05938738 1.05938738 1.059811729 1.0598599531 0.00023454 5.5009E-08 -0.001096079 1.20139E-06	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 surments: 4 positions, 5 repeatitions each Position 2 1.0627 1.0626 1.0626 1.0626 1.0626 1.0626 1.0626 1.062696861 0.000176222 3.10541E-08 0.002001252 4.00501E-06	Calibrated length /mm 0.500000 Position 3 1.0612 1.0614 1.0616 1.0608 1.0614 1.0618 8.4865E-08 0.000586864	U calibration inseries U calibration inseries 0.0001 Position 4 1.0591 1.0592 1.0592 1.0592 1.0592 1.0592 1.0592 1.0592 0.000209743 4.39922E-0.00 0.00149203	0.5	Measurements No. 1 2	Position 1 Po 0.5009 0.5013	0.5009 0.5013	0.50 0.50
0.75 Type Gauge block Measurement repetition name 22-29 22-29 22-29 22-29 22-29 22-29 (S) (S))*2 yı yı yı yı yı	2.22E-05 Part number Calibration mea: Position 1 1.059882357 1.05982881 1.05938738 1.05938738 1.05938738 1.059811729 1.059599531 0.00023454 5.5009E-08 -0.001096079	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 surments: 4 positions, 5 repeatitions each Position 2 1.0627 1.0626 1.0626 1.0626 1.0626 1.0626 1.0626 1.062696861 0.000176222 3.10541E-08 0.002001252 4.00501E-06	Calibrated length /mm 0.500000 Position 3 1.0612 1.0614 1.0616 1.0608 1.0614 1.0618 8.4865E-08 0.000586864	U calibration inseries U calibration inseries 0.0001 Position 4 1.0591 1.0592 1.0592 1.0592 1.0592 1.0592 1.0592 1.0592 0.000209743 4.39922E-0.00 0.00149203	0.5	Measurements No. 1 2	Position 1 Po 0.5009 0.5013	0.5009 0.5013	0.50 0.50
0.75 Type Gauge block Measurement repetition name 22-29 22-29 22-29 22-29 22-29 22-29 y _i (S _i)'22 y _i - y' y'	2.22E-05 Part number Calibration mea: Position 1 1.05988.2357 1.05952881 1.05938738 1.05938738 1.059811729 1.0598599531 0.00023454 5.5009E-08 -0.001096079 1.20139E-06	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 surments: 4 positions, 5 repeatitions each Position 2 1.0627 1.0626 1.0626 1.0626 1.0626 1.0626 1.0626896861 0.000176222 3.10541E-08 0.002001252 4.00501E-06	Calibrated length /mm 0.500000 Position 3 1.0612 1.0614 1.0616 1.0608 1.0614 1.0618 8.4865E-08 0.000586864	U calibration inseries U calibration inseries 0.0001 Position 4 1.0591 1.0592 1.0592 1.0592 1.0592 1.0592 1.0592 1.0592 0.000209743 4.39922E-0.00 0.00149203	0.5	Measurements No. 1 2	Position 1 Po 0.5009 0.5013	0.5009 0.5013	0.50 0.50
0.75 Type Gauge block Measurement repetition name 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 Coverage factor (p)	2.22E-05 Part number Calibration mea: Position 1 1.059882357 1.05952881 1.05938738 1.05981729 1.05999531 0.00023454 5.5009E-08 0.001096079 1.20139E-06	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 surments: 4 positions, 5 repeatitions each Position 2 1.0627 1.0626 1.0626 1.0630 1.0626 1.0626 1.0630 1.0626 1.062696861 0.000176222 3.10541E-08 0.002001252 4.00501E-06	Calibrated length /mm 0.500000 Position 3 1.0612 1.0614 1.0616 1.0608 1.0614 1.061282474 0.000297467 8.84865E-08 0.000586864 3.4441E-07	U calibration inseries U calibration inseries 0.0001 Position 4 1.0591 1.0592 1.0592 1.0592 1.0592 1.0592 1.0592 1.0592 0.000209743 4.39922E-0.00 0.00149203	0.5	Measurements No. 1 2 3	Position 1 Po 0.5009 0.5013 0.5002	0.5009 0.5013	0.50 0.50
0.75 Type Gauge block Measurement repetition name 22-29 22-29 22-29 22-29 22-29 3, (S,)'2 y,'-y'/2 (y,-y)'/2 Coverage factor (p) y	2.22E-05 Part number Calibration mea: Position 1 1.059882357 1.05982881 1.05938738 1.05938738 1.05938738 1.059911729 1.059399531 0.00023454 5.5009E-08 -0.001096079 1.20139E-06	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 surments: 4 positions, 5 repeatitions each Position 2 1.0627 1.0626 1.0626 1.0626 1.0626 1.0626861 0.000176222 3.10841E-08 0.002001252 4.00501E-06	Calibrated length /mm 0.500000 Position 3 1.0612 1.0614 1.0616 1.0608 1.0614 1.0618 2.000297467 8.84865E-08 0.000586864 3.4441E-07	U calibration inseries U calibration inseries 0.0001 Position 4 1.0591 1.0592 1.0592 1.0592 1.0592 1.0592 1.0592 1.0592 0.000209743 4.39922E-0.00 0.00149203	0.5	Measurements No. 1 2 3 3	Position 1 Po 0.5009 0.5013 0.5002	0.5009 0.5013	0.50 0.50
Type Gauge block Measurement repetition name 22-29 22-29 22-29 22-29 22-29 3, (S,)'2 y,'-y''2 Coverage factor (p) y	2.22E-05 Part number Calibration mea: Position 1 1.05988.2357 1.05952881 1.05938738 1.05981729 1.059599531 0.00023454 5.5009E-08 -0.001096079 1.20139E-06 95.45] %	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 surments: 4 positions, 5 repeatitions each Position 2 1.0627 1.0626 1.0626 1.0626 1.0626 1.0626 1.0626 1.0626 0.000176222 3.10541E-08 0.00201252 4.00501E-06	Calibrated length /mm 0.500000 Position 3 1.0612 1.0614 1.0616 1.0608 1.0614 1.0618 2.000297467 8.84865E-08 0.000586864 3.4441E-07	U calibration inseries U calibration inseries 0.0001 Position 4 1.0591 1.0592 1.0592 1.0592 1.0592 1.0592 1.0592 1.0592 0.000209743 4.39922E-0.00 0.00149203	0.5	Measurements No. 1 2 3	Position 1 Po	0.5009 0.5013 0.5002	0.50 0.50
0.75 Type Gauge block Measurement repetition name 22-29 22-29 22-29 22-29 22-29 3, (S,)'2 y,'-y'/2 (y,-y)'/2 Coverage factor (p) y	2.22E-05 Part number Calibration mea: Position 1 1.059882357 1.05982881 1.05938738 1.05938738 1.05938738 1.059911729 1.059399531 0.00023454 5.5009E-08 -0.001096079 1.20139E-06	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 surments: 4 positions, 5 repeatitions each Position 2 1.0627 1.0626 1.0626 1.0626 1.0626 1.0626861 0.000176222 3.10841E-08 0.002001252 4.00501E-06	Calibrated length /mm 0.500000 Position 3 1.0612 1.0614 1.0616 1.0608 1.0614 1.0618 2.000297467 8.84865E-08 0.000586864 3.4441E-07	U calibration inseries U calibration inseries 0.0001 Position 4 1.0591 1.0592 1.0592 1.0592 1.0592 1.0592 1.0592 1.0592 0.000209743 4.39922E-0.00 0.00149203	0.5	Measurements No. 1 2 3 3	Position 1 Po 0.5009 0.5013 0.5002	0.5009 0.5013 0.5002	0.50 0.50
Type Gauge block Measurement repetition name 22-29 22-29 22-29 22-29 22-29 3, (S,)'2 y,'-y''2 Coverage factor (p) y	2.22E-05 Part number Calibration mea: Position 1 1.05988.2357 1.05952881 1.05938738 1.05981729 1.059599531 0.00023454 5.5009E-08 -0.001096079 1.20139E-06 95.45] %	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 surments: 4 positions, 5 repeatitions each Position 2 1.0627 1.0626 1.0626 1.0626 1.0626 1.0626 1.0626 1.0626 0.000176222 3.10541E-08 0.00201252 4.00501E-06	Calibrated length /mm 0.500000 Position 3 1.0612 1.0614 1.0616 1.0608 1.0614 1.0618 2.000297467 8.84865E-08 0.000586864 3.4441E-07	U calibration inseries U calibration inseries 0.0001 Position 4 1.0591 1.0592 1.0592 1.0592 1.0592 1.0592 1.0592 1.0592 0.000209743 4.39922E-0.00 0.00149203	0.5	Measurements No. 1 2 3 E _{Lprop}	Position 1 Po	0.5009 0.5013 0.5002	0.50 0.50
0.75 Type Gauge block Measurement repetition name 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 y ₁ y ₁ y ₂ y ₁ -y ² Coverage factor (p) y U _{rep} U _{geo} E _L	2.22E-05 Part number Calibration meat Position 1 1.05982357 1.05982357 1.05938738 1.05938738 1.05938738 1.05938738 1.05938738 1.05938738 1.05938738 1.05938738 1.05938738 1.059599531 0.00023454 5.5009E-08 -0.001096079 1.20139E-06 95.45 % 1.06069561 0.000233742 0.000805035	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 surments: 4 positions, 5 repeatitions each Position 2 1.0627 1.0626 1.0626 1.0626 1.0626 1.0626 1.0626 1.0626 1.0626 1.0626 1.0626 1.0626 1.0626 1.0627 1.0626 1.062	0.003333333 Calibrated length /mm 0.500000 Position 3 1.0612 1.0614 1.0618 1.0618 1.0618 1.0618 1.0618 1.0618 2.00297467 8.84865E-08 0.000586864 3.4441E-07 u_4 - / V_c 7.46258E-18 8.75021E-15	U calibration inseries U calibration inseries 0.0001 Position 4 1.0591 1.0592 1.0592 1.0592 1.0592 1.0592 1.0592 1.0592 0.000209743 4.39922E-0.00 0.00149203	0.5	Measurements No. 1 2 3 E _{Lprop}	Position 1 Po	0.5009 0.5013 0.5002	0.50 0.50
Type Gauge block Measurement repetition name 22-29 22-29 22-29 22-29 22-29 22-29 21-29 21-29 22-29 22-29 21-29 2	2.22E-05 Part number Calibration mea: Position 1 1.059882357 1.05952881 1.05938738 1.05981738 1.05981729 1.05999531 0.00023454 5.5009E-08 95.45] % 1.06069561	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 surments: 4 positions, 5 repeatitions each Position 2 1.0627 1.0626 1.0626 1.0626 1.0626 1.0626 1.0626 1.0626 0.000176222 3.10541E-08 0.00201252 4.00501E-06	Calibrated length /mm 0.500000 Position 3 1.0612 1.0614 1.0616 1.0608 1.0614 1.0618 2.000297467 8.84865E-08 0.000586864 3.4441E-07	U calibration inseries U calibration inseries 0.0001 Position 4 1.0591 1.0592 1.0592 1.0592 1.0592 1.0592 1.0592 1.0592 0.000209743 4.39922E-0.00 0.00149203	0.5	Measurements No. 1 2 3 E _{Lprop}	Position 1 Po	0.5009 0.5013 0.5002	0.50 0.50
0.75 Type Gauge block Measurement repetition name 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 y ₁ y ₁ y ₂ y ₁ -y ² Coverage factor (p) y U _{rep} U _{geo} E _L	2.22E-05 Part number Calibration meat Position 1 1.05982357 1.05982357 1.05938738 1.05938738 1.05938738 1.05938738 1.05938738 1.05938738 1.05938738 1.05938738 1.05938738 1.059599531 0.00023454 5.5009E-08 -0.001096079 1.20139E-06 95.45 % 1.06069561 0.000233742 0.000805035	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 surments: 4 positions, 5 repeatitions each Position 2 1.0627 1.0626 1.0626 1.0630 1.0626 1.0626 1.06269681 0.000176222 3.10541E-08 0.002001252 4.00501E-06	0.003333333 Calibrated length /mm 0.500000 Position 3 1.0612 1.0614 1.0618 1.0618 1.0618 1.0618 1.0618 1.0618 2.00297467 8.84865E-08 0.000586864 3.4441E-07 u_4 - / V_c 7.46258E-18 8.75021E-15	U calibration inseries U calibration inseries 0.0001 Position 4 1.0591 1.0592 1.0592 1.0592 1.0592 1.0592 1.0592 1.0592 0.000209743 4.39922E-0.00 0.00149203	0.5	Measurements No. 1 2 3 E _{Lprop}	Position 1 Po	0.5009 0.5013 0.5002	0.50 0.50
0.75 Type Gauge block Measurement repetition name 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 23-29 24-29 25-29 26-29 27-29 28-29 29-29 29-29 29-29 20-29 2	2.22E-05 Part number Calibration meat Position 1 1.059882357 1.05982387 1.05938738 1.05938738 1.05938738 1.05938738 1.05938738 1.05938738 1.05938738 1.05938738 1.05938738 1.05938738 1.05961729 1.06069561 95.45 % 1.06069561 0.000233742 0.000233742 0.000805035 0.0012	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 surments: 4 positions, 5 repeatitions each Position 2 1.0627 1.0626 1.0626 1.0630 1.0626 1.06266 1.062696861 0.000176222 3.10541E-08 0.002001252 4.00501E-06	Calibrated length /mm 0.500000 Position 3 1.0612 1.0614 1.0616 1.0608 1.0614 1.0618282474 0.000297467 8.84865E-08 0.00098864 3.4441E-07 u _e ⁴ /v _e 7.46258E-18 8.75021E-15	U calibration inseries U calibration inseries 0.0001 Position 4 1.0591 1.0592 1.0592 1.0592 1.0592 1.0592 1.0592 1.0592 0.000209743 4.39922E-0.00 0.00149203	0.5	Measurements No. 1 2 3 E _{Lprop}	Position 1 Po	0.5009 0.5013 0.5002	0.50 0.50
0.75 Type Gauge block Measurement repetition name 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-20 y ₁ S ₁ (S ₁) ² y ₁ - y ₁ ² (Y ₁ - y) ² Coverage factor (p) y u _{rep} u _{geo} E _L u _{corr} u _{ttemp}	2.22E-05 Part number Calibration mea: Position 1 1.05988.2357 1.05952881 1.05938738 1.05938738 1.059811729 1.0598599531 0.00023454 5.5009E-08 -0.001096079 1.20139E-06 95.45] % 1.06069561 0.000233742 0.000805035 0.0012 0.000252488	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 surments: 4 positions, 5 repeatitions each Position 2 1.0627 1.0626 1.0626 1.0630 1.0626 1.06266 1.062696861 0.000176222 3.10541E-08 0.002001252 4.00501E-06	Calibrated length /mm 0.500000 Position 3 1.0612 1.0614 1.0616 1.0608 1.0614 1.0618 2.000297467 8.84865E-08 0.000588664 3.4441E-07 u _e ⁴ /v _e 7.46258E-18 8.75021E-15 4.51562E-16 0	5.7735E-08 Uasilization interm 0.0001 Position 4 1.0591 1.0592 1.0592 1.0592 1.0592 1.0592 3.000209743 4.39922E-000209743 2.22618E-06	0.5	Measurements No. 1 2 3 E _{Lprop}	Position 1 Po	0.5009 0.5013 0.5002	0.50 0.50
Type Gauge block Measurement repetition name 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-20 y ₁ S ₁ (S ₁) ² y ₁ - y ₁ ² (y ₁ - y) ² Coverage factor (p) y u _{rep} u _{geo} E _L u _{corr} u _{temp} Calibrated value	2.22E-05 Part number Calibration mea: Position 1 1.059882357 1.05952881 1.05938738 1.05981738 1.05981729 1.059990531 0.00023454 5.5009E-08 95.45] % 1.06069561 0.000233742 0.000233742 0.000805035 0.0012 0.000252488 9.95739E-07	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 surments: 4 positions, 5 repeatitions each Position 2 1.0627 1.0626 1.0626 1.0630 1.0626 1.06266 1.062696861 0.000176222 3.10541E-08 0.002001252 4.00501E-06	Calibrated length /mm 0.500000 Position 3 1.0612 1.0614 1.0616 1.0608 1.0614 1.0618282474 0.000297467 8.84865E-08 0.00098864 3.4441E-07 u _e ⁴ /v _e 7.46258E-18 8.75021E-15	U calibration inseries U calibration inseries 0.0001 Position 4 1.0591 1.0592 1.0592 1.0592 1.0592 1.0592 1.0592 1.0592 0.000209743 4.39922E-0.00 0.00149203	0.5	Measurements No. 1 2 3 E _{Lprop}	Position 1 Po	0.5009 0.5013 0.5002	0.50 0.50
0.75 Type Gauge block Measurement repetition name 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 Vi Si (Si)'22 Yi - Yy'2 (Yi - Yy'2 Coverage factor (p) y u _{rep} u _{geo} EL u _{corr} u _{ttemp}	2.22E-05 Part number Calibration mea: Position 1 1.05988.2357 1.05952881 1.05938738 1.05938738 1.059811729 1.0598599531 0.00023454 5.5009E-08 -0.001096079 1.20139E-06 95.45] % 1.06069561 0.000233742 0.000805035 0.0012 0.000252488	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 surments: 4 positions, 5 repeatitions each Position 2 1.0627 1.0626 1.0626 1.0630 1.0626 1.06266 1.062696861 0.000176222 3.10541E-08 0.002001252 4.00501E-06	Calibrated length /mm 0.500000 Position 3 1.0612 1.0614 1.0616 1.0608 1.0614 1.0618 2.000297467 8.84865E-08 0.000588664 3.4441E-07 u _e ⁴ /v _e 7.46258E-18 8.75021E-15 4.51562E-16 0	5.7735E-08 Uasilization interm 0.0001 Position 4 1.0591 1.0592 1.0592 1.0592 1.0592 1.0592 3.000209743 4.39922E-000209743 2.22618E-06	0.5	Measurements No. 1 2 3 E _{Lprop}	Position 1 Po	0.5009 0.5013 0.5002	0.50 0.50
Type Gauge block Measurement repetition name 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 23-29 24-29 25-29 25-29 26-29 27-29 28-29 29-29 29-29 29-29 29-29 29-29 29-29 29-29 29-29 29-29 29-29 29-29 29-29 29-29 29-29 29-29 29-29 29-29 29-29 29-29 20-29 2	2.22E-05 Part number Calibration meat Position 1 1.05982337 1.05982337 1.05982381 1.05938738 1.05938738 1.059811729 1.059599531 0.00023454 5.5009E-08 -0.001096079 1.20139E-06 1.06069561 0.000233742 0.000233742 0.00085035 0.0012 0.000252488 9.95739E-07	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 surments: 4 positions, 5 repeatitions each Position 2 1.0627 1.0626 1.0626 1.0630 1.0626 1.06266 1.062696861 0.000176222 3.10541E-08 0.002001252 4.00501E-06	Calibrated length /mm 0.500000 Position 3 1.0612 1.0614 1.0616 1.0608 1.0614 1.0618 2.000297467 8.84865E-08 0.000588664 3.4441E-07 u _e ⁴ /v _e 7.46258E-18 8.75021E-15 4.51562E-16 0	5.7735E-08 Uasilization interm 0.0001 Position 4 1.0591 1.0592 1.0592 1.0592 1.0592 1.0592 3.000209743 4.39922E-000209743 2.22618E-06	0.5	Measurements No. 1 2 3 E _{Lprop}	Position 1 Po	0.5009 0.5013 0.5002	0.50 0.50
Type Gauge block Measurement repetition name 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-29 22-20 y ₁ S ₁ (S ₁) ² y ₁ - y ₁ ² (y ₁ - y) ² Coverage factor (p) y u _{rep} u _{geo} E _L u _{corr} u _{temp} Calibrated value	2.22E-05 Part number Calibration mea: Position 1 1.059882357 1.05952881 1.05938738 1.05981738 1.05981729 1.059990531 0.00023454 5.5009E-08 95.45] % 1.06069561 0.000233742 0.000233742 0.000805035 0.0012 0.000252488 9.95739E-07	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 surments: 4 positions, 5 repeatitions each Position 2 1.0627 1.0626 1.0626 1.0630 1.0626 1.06266 1.062696861 0.000176222 3.10541E-08 0.002001252 4.00501E-06	Calibrated length /mm 0.500000 Position 3 1.0612 1.0614 1.0616 1.0608 1.0614 1.0618 2.000297467 8.84865E-08 0.000588664 3.4441E-07 u _e ⁴ /v _e 7.46258E-18 8.75021E-15 4.51562E-16 0	5.7735E-08 Uasilization interm 0.0001 Position 4 1.0591 1.0592 1.0592 1.0592 1.0592 1.0592 3.000209743 4.39922E-000209743 2.22618E-06	0.5	Measurements No. 1 2 3 E _{Lprop}	Position 1 Po	0.5009 0.5013 0.5002	0.50 0.50

Calibrated value

standard uncertainty

CALCULATION OF LENGTH CALIBRATION

		Object of calibration]			
Length of measurement [mm]	CTE [K-1]	Uncertainty of CTE (uaw) [K-1]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	$u_{\alpha M}$		$(C) = (T_W - 20^{\circ}C)$			
0.75	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5				
		Reference artefact used]			
Type	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k A				
Gauge block	-	0.75	0.500000	0.000)1 2				
	Calibration me	asurments: 4 positions, 5 repeatitions each	1				Gauge block measuremen	nt	
Measurement repetition name	Position 1 1.061155149	Position 2 1.0600	Position 3 1.0605	Position 4 1.0614	4	Measurements No.	Position 1	Position 2	Position 3
29-36 29-36	1.061013841	1.0500	1.0604	1.0614		2	0.5009 0.5013	0.5009 0.5013	0.5009 0.5013
29-36	1.061155149	1.0598	1.0608	1.0613		3	0.5002	0.5002	0.5002
29-36	1.061013916	1.0591	1.0608	1.0609			0.0002	0.0002	0.0002
29-36	1.06101401	1.0597	1.0601	1.0608					
y _j S _j	1.061070413	1.059656194	1.060518975	1.061098588					
S _j	7.7353E-05 5.98349E-09	0.000340469	0.000300126 9.00753E-08	0.000236643					
(S _j)^2	0.000484371	1.15919E-07 -0.000929848	9.00753E-08 -6.70676E-05	5.59999E-08 0.000512545					
y _i - y (y _i - y)^2	2.34615E-07	8.64618E-07	4.49806E-09	2.62703E-07					
	•				_				
Coverage factor (p)	95.45	%							
у	1.060586042					E _{Lprop}	0.0016		
,		l.							
		Degree of freedom (v _e)	u_e^4 / v_e						
U _{rep}	0.000258833	16	1.12206E-17			L _{measstd}	0.5008		
	0.000337446	3	2.7013E-16				0.000482183	gree of freedom 8	
U _{geo}	0.000337440	3	2.1013E-10			U _{measstd}	0.000402103	U	
E⊾	0.0012								
	0.000252488	9	4.51562E-16						
Ucorr	0.000252488	9	4.51502E-10						
U _{temp}	9.95739E-07	∞	0						
			1						
Calibrated value	1.059386042	1	Effective degree of freedom	15	_				
Calibrated Value	1:039380042		Lilective degree of freedom						
standard uncertainty	0.000324988								
k factor	2.181165682								
Extended uncertainty	0.000708853								
Extended uncertainty	0.000708853								
Extended uncertainty	0.000708853	CALCIII ATION	OF LENCT	II CAI IDI	D ATI)N			
Extended uncertainty	0.000708853	CALCULATION	OF LENGTI	H CALIBI	RATI(ON			
Extended uncertainty	0.000708853	CALCULATION	OF LENGTI	H CALIBI	RATI(ON			
Extended uncertainty	0.000708853	CALCULATION	OF LENGTI	H CALIBI	RATIO	ON			
Extended uncertainty	0.000708853	CALCULATION	OF LENGTI	H CALIBI	RATI(ON			
Extended uncertainty	0.000708853		OF LENGTI	H CALIBI	RATIO	ON			
		Object of calibration				1			
Length of measurement [mm]	CTE [K ⁺]	$\begin{array}{c} \text{Object of calibration} \\ \text{Uncertainty of CTE}\left(u_{sw}\right)\left[K^{-1}\right] \end{array}$	$(u^2_{TW} + u^2_{TWS})[K^2]$	${ m u_{aM}}$	(T _M – 20°C) C) = (T _w - 20°C)			
		Object of calibration				1			
Length of measurement [mm]	CTE [K ⁺]	$\begin{array}{c} \text{Object of calibration} \\ \text{Uncertainty of CTE}\left(u_{sw}\right)\left[K^{-1}\right] \end{array}$	$(u^2_{TW} + u^2_{TWS})[K^2]$	${ m u_{aM}}$	(T _M – 20°C	1			
Length of measurement [mm]	CTE [K ¹] 2.22E-05	Object of calibration Uncertainty of CTE (u_{aw}) [K^{-1}] 0.00000069	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333	Ա _մ	(T _M - 20°(1			
Length of measurement [mm] 0.75	CTE [K ⁺]	Object of calibration Uncertainty of CTE (u_{*w}) [K^{-1}] 0.0000069 Reference artefact used Nominal length /mm	$\begin{array}{c} (u^2_{\rm TW} + u^2_{\rm TWS}) [K^2] \\ 0.003333333 \end{array}$	U _a M 5.7735E-08	(T _M - 20°(1			
Length of measurement [mm]	CTE [K ¹] 2.22E-05	Object of calibration Uncertainty of CTE (u_{aw}) [K^{-1}] 0.00000069	$\begin{array}{c} (u^2_{\text{TW}} + u^2_{\text{TWS}}) [K^2] \\ 0.003333333 \end{array}$	Ա _մ	(T _M - 20°(1			
Length of measurement [mm] 0.75	CTE [K ⁺] 2.22E-05 Part number	Object of calibration Uncertainty of CTE (u _{aw}) [K¹] 0.0000069 Reference artefact used Nominal length /mm 0.75	$\begin{array}{c} (u^2_{\text{TW}} + u^2_{\text{TWS}}) [K^2] \\ 0.0033333333 \\ \\ \hline \text{Calibrated length /mm} \\ 0.500000 \\ \end{array}$	U _a M 5.7735E-08	(T _M - 20°(1			
Length of measurement [mm] 0.75 Type Gauge block	CTE [K¹] 2.22E-05 Part number Calibration me	Object of calibration Uncertainty of CTE (u _{cw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75	(u² _{TW} + u² _{TNS}) [K²] 0.003333333 Calibrated length /mm 0.500000	U _{sM} 5.7735E-08 U_saltoration.imm 0.0000	(T _M - 20°($C = (T_W - 20^{\circ}C)$	Gauge block measuremer		Doubles 2
Length of measurement [mm] 0.75 Type Gauge block Measurement repetition name	CTE [K¹] 2.22E-05 Part number - Calibration me Position 1	$\begin{array}{c} \text{Object of calibration} \\ \text{Uncertainty of CTE} \left(u_{aw}\right)\left[K^{-1}\right] \\ \text{0.0000069} \\ \\ \text{Reference artefact used} \\ \text{Nominal length /mm} \\ \text{0.75} \\ \\ \text{assurments: 4 positions, 5 repeatitions each} \\ \text{Position 2} \end{array}$		U _{sM} 5.7735E-08 U _{sath-atton mm} 0.000 Position 4	(T _M - 20°(C) = (T _w – 20°C)	Position 1	Position 2	Position 3
Length of measurement [mm] 0.75 Type Gauge block Measurement repetition name 6-11	CTE [K¹]	Object of calibration Uncertainty of CTE (u _{sw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 1.0614	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 0.500000	U _{oM} 5.7735E-08 U _{calibration imm} 0.000 Position 4 1.0604	(T _M - 20°(Position 1 0.5009	Position 2 0.5009	0.5009
Length of measurement [mm] 0.75 Type Gauge block Measurement repetition name 6-11 6-11	CTE [K¹] 2.22E-05 Part number - Calibration me Position 1 1.060306809 1.060589652	Object of calibration Uncertainty of CTE (u_{sw}) [K^{-1}] 0.0000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions, 5 repeatitions each Position 2 1.0614 1.0609	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 0.500000 Position 3 1.0604 1.0609	U _{sM} 5.7735E-08 U _{salbation /mm} 0.000 Position 4 1.0604 1.0607	(T _M - 20°(C) = (T _w - 20°C)	Position 1 0.5009 0.5013	Position 2 0.5009 0.5013	0.5009 0.5013
Length of measurement [mm] 0.75 Type Gauge block Measurement repetition name 6-11 6-11 6-11	CTE [K¹]	Object of calibration Uncertainty of CTE (u _{sw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 1.0614	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 0.500000	U _{oM} 5.7735E-08 U _{calibration imm} 0.000 Position 4 1.0604	(T _M - 20°(Position 1 0.5009	Position 2 0.5009	0.5009
Length of measurement [mm] 0.75 Type Gauge block Measurement repetition name 6-11 6-11 6-11 6-11	CTE [K¹] 2.22E-05 Part number Calibration me Position 1 1.060306809 1.06037669	Object of calibration Uncertainty of CTE (u _{sw}) [K¹] 0.0000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions, 5 repeatitions each Position 2 1.0614 1.0609 1.0607	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 0.500000 Position 3 1.0604 1.0609 1.0612	U _{eM} 5.7735E-08 U _{calibration imm} 0.000 Position 4 1.0604 1.0607 1.0612	(T _M - 20°(C) = (T _w - 20°C)	Position 1 0.5009 0.5013	Position 2 0.5009 0.5013	0.5009 0.5013
Length of measurement [mm] 0.75 Type Gauge block Measurement repetition name 6-11 6-11 6-11 6-11 6-11 6-11	CTE [K¹] 2.22E-05 Part number Calibration me Position 1 1.060306809 1.060389652 1.060377669 1.061084775 1.060307149 1.060533211	Object of calibration Uncertainty of CTE (u _{aw}) [K-1] 0.0000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions, 5 repeatitions each Position 2 1.0614 1.0609 1.0608 1.0609 1.06099	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 0.500000 Position 3 1.0604 1.0609 1.0612 1.0611 1.0609 1.06090727	U _{salteration imm} 5.7735E-08 U _{salteration imm} 0.000 Position 4 1.0604 1.0607 1.0612 1.0604 1.0607 1.06070274	(T _M - 20°(C) = (T _w - 20°C)	Position 1 0.5009 0.5013	Position 2 0.5009 0.5013	0.5009 0.5013
Length of measurement [mm] 0.75 Type Gauge block Measurement repetition name 6-11 6-11 6-11 6-11 6-11 5,	CTE [K¹] 2.22E-05 Part number Calibration me Position 1 1.060306809 1.060389652 1.060377669 1.060307149 1.06033211 0.00032938	Object of calibration Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.0000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 1.0614 1.0609 1.0607 1.0608 1.0609 1.060943094 0.00028279	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 0.500000 Position 3 1.0604 1.0609 1.0612 1.0611 1.0609 1.06090727 0.000294154	U _{shM} 5.7735E-08 U _{saboration rimm} 0.000 Position 4 1.0604 1.0607 1.0612 1.0604 1.0607 1.06070274 0.00028975	(T _M - 20°(C) = (T _w - 20°C)	Position 1 0.5009 0.5013	Position 2 0.5009 0.5013	0.5009 0.5013
Length of measurement [mm] 0.75 Type Gauge block Measurement repetition name 6-11 6-11 6-11 6-11 6-11 8-11 (S) (S)/2	CTE [K¹] 2.22E-05 Part number Calibration me Position 1 1.060306809 1.060389652 1.060377669 1.061084775 1.060307149 1.060533211 0.00032938 1.08491E-07	Object of calibration Uncertainty of CTE (u _{aw}) [K-1] 0.0000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions, 5 repeatitions each Position 2 1.0614 1.0609 1.0608 1.0609 1.06099	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 0.500000 Position 3 1.0604 1.0609 1.0612 1.0611 1.0609 1.06090727	U _{salteration imm} 5.7735E-08 U _{salteration imm} 0.000 Position 4 1.0604 1.0607 1.0612 1.0604 1.0607 1.06070274	(T _M - 20°(C) = (T _w - 20°C)	Position 1 0.5009 0.5013	Position 2 0.5009 0.5013	0.5009 0.5013
Length of measurement [mm] 0.75 Type Gauge block Measurement repetition name 6-11 6-11 6-11 6-11 6-11 5,	CTE [K¹] 2.22E-05 Part number Calibration me Position 1 1.060306809 1.06037669 1.061084775 1.060307149 1.060533211 0.00032938 1.08491E-07	Object of calibration Uncertainty of CTE (u _{aw}) [K¹] 0.0000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions, 5 repeatitions each Position 2 1.0614 1.0609 1.0608 1.0609 1.060943094 0.00028279 7.99702E-08	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 0.500000 Position 3 1.0604 1.0609 1.0612 1.0611 1.0609 1.06090727 0.000294154 8.65266E-08	U _{salteration imm} 0.000 Position 4 1.0604 1.0607 1.0612 1.0604 1.0607 1.06070274 0.00028975 8.39552E-08	(T _M - 20°(C) = (T _w - 20°C)	Position 1 0.5009 0.5013	Position 2 0.5009 0.5013	0.5009 0.5013
Length of measurement [mm] 0.75	CTE [K*] 2.22E-05 Part number Calibration me Position 1 1.060306809 1.060389652 1.060377669 1.061084775 1.060307149 1.08053211 0.00032938 1.08491E-07 -0.000236732 5.60421E-08	Object of calibration Uncertainty of CTE (u _{*w}) [K ⁻¹] 0.0000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions, 5 repeatitions each Position 2 1.0614 1.0609 1.0607 1.0608 1.0609 1.060943094 0.00028279 7.99702E-08 0.000173151 2.99812E-08	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 0.500000 1.0604 1.0609 1.0612 1.06300727 0.000294154 8.65266E-08	U _{sabdison frem} 5.7735E-08 U _{sabdison frem} 0.000 Position 4 1.0607 1.0607 1.0612 1.0607 1.060707 1.060707 1.060707 1.0607074 0.00028975 8.39552E-08	(T _M - 20°(C) = (T _w - 20°C)	Position 1 0.5009 0.5013	Position 2 0.5009 0.5013	0.5009 0.5013
Length of measurement [mm] 0.75 Type Gauge block Measurement repetition name 6-11 6-11 6-11 6-11 9, (S,)**2 y, - y	CTE [K*] 2.22E-05 Part number Calibration me Position 1 1.060306809 1.060389652 1.060377669 1.061084775 1.060307149 1.080533211 0.00032938 1.08491E-07 -0.000236732	Object of calibration Uncertainty of CTE (u _{*w}) [K ⁻¹] 0.0000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions, 5 repeatitions each Position 2 1.0614 1.0609 1.0607 1.0608 1.0609 1.060943094 0.00028279 7.99702E-08 0.000173151 2.99812E-08	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 0.500000 1.0604 1.0609 1.0612 1.06300727 0.000294154 8.65266E-08	U _{sabdison frem} 5.7735E-08 U _{sabdison frem} 0.000 Position 4 1.0607 1.0607 1.0612 1.0607 1.060707 1.060707 1.060707 1.0607074 0.00028975 8.39552E-08	(T _M - 20°(C) = (T _w - 20°C)	Position 1 0.5009 0.5013	Position 2 0.5009 0.5013	0.5009 0.5013
Length of measurement [mm] 0.75	CTE [K*] 2.22E-05 Part number Calibration me Position 1 1.060306809 1.060389652 1.060377669 1.061084775 1.060307149 1.08053211 0.00032938 1.08491E-07 -0.000236732 5.60421E-08	Object of calibration Uncertainty of CTE (u _{*w}) [K ⁻¹] 0.0000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions, 5 repeatitions each Position 2 1.0614 1.0609 1.0607 1.0608 1.0609 1.060943094 0.00028279 7.99702E-08 0.000173151 2.99812E-08	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 0.500000 1.0604 1.0609 1.0612 1.06300727 0.000294154 8.65266E-08	U _{sabdison frem} 5.7735E-08 U _{sabdison frem} 0.000 Position 4 1.0607 1.0607 1.0612 1.0607 1.060707 1.060707 1.060707 1.0607074 0.00028975 8.39552E-08	(T _M - 20°(C) = (T _w - 20°C)	Position 1 0.5009 0.5013	Position 2 0.5009 0.5013	0.5009 0.5013
Length of measurement [mm] 0.75 Type Gauge block Measurement repetition name 6-11 6-11 6-11 6-11 6-11 6-11 9, S, S, Y-2 9, Y, -Y (y, - y)*2 Coverage factor (p)	CTE [K*] 2.22E-05 Part number Calibration me Position 1 1.060306809 1.06038652 1.06037669 1.061084775 1.060307149 1.060533211 0.00032938 1.08491207 -0.00036732 5.60421E-08	Object of calibration Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions, 5 repeatitions each Position 2 1.0614 1.0609 1.0608 1.06094 0.00228279 7.99702E-08 0.000173151 2.99812E-08	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 0.500000 Position 3 1.0604 1.0609 1.0612 1.0611 1.0609 1.060900727 0.000294154 8.65266E-08 0.000130784 1.71045E-08	U _{sabdison frem} 5.7735E-08 U _{sabdison frem} 0.000 Position 4 1.0607 1.0607 1.0612 1.0607 1.060707 1.060707 1.060707 1.0607074 0.00028975 8.39552E-08	(T _M - 20°($\begin{bmatrix} C \\ C \end{bmatrix} = (T_W - 20^{\circ}C)$ $\begin{bmatrix} Measurements No. \\ 1 \\ 2 \\ 3 \end{bmatrix}$	Position 1 0.5009 0.5013 0.5002	Position 2 0.5009 0.5013	0.5009 0.5013
Length of measurement [mm] 0.75	CTE [K*] 2.22E-05 Part number Calibration me Position 1 1.060306809 1.06037669 1.060377669 1.060307149 1.060533211 0.00032938 1.08491E-07 -0.000236732 5.60421E-08	Object of calibration Uncertainty of CTE (u _{sw}) [K-1] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 1.0614 1.0609 1.0607 1.0608 1.0609 1.060943094 0.0028279 7.99702E-08 0.000173151 2.99812E-08	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 0.500000 Position 3 1.0604 1.0609 1.0612 1.0611 1.0609 1.06224154 8.65266E-08 0.000130784 1.71045E-08	U _{sabdison frem} 5.7735E-08 U _{sabdison frem} 0.000 Position 4 1.0607 1.0607 1.0612 1.0607 1.060707 1.060707 1.060707 1.0607074 0.00028975 8.39552E-08	(T _M - 20°(C) = (T _W - 20°C) Measurements No. 1 2 3	Position 1	Position 2 0.5009 0.5013	0.5009 0.5013
Length of measurement [mm] 0.75 Type Gauge block Measurement repetition name 6-11 6-11 6-11 6-11 6-11 6-11 9, S, S, Y-2 9, Y, -Y (y, - y)*2 Coverage factor (p)	CTE [K*] 2.22E-05 Part number Calibration me Position 1 1.060306809 1.06038652 1.06037669 1.061084775 1.060307149 1.060533211 0.00032938 1.08491207 -0.00036732 5.60421E-08	Object of calibration Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions, 5 repeatitions each Position 2 1.0614 1.0609 1.0608 1.06094 0.00228279 7.99702E-08 0.000173151 2.99812E-08	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 0.500000 Position 3 1.0604 1.0609 1.0612 1.0611 1.0609 1.060900727 0.000294154 8.65266E-08 0.000130784 1.71045E-08	U _{sabdison frem} 5.7735E-08 U _{sabdison frem} 0.000 Position 4 1.0607 1.0607 1.0612 1.0607 1.060707 1.060707 1.060707 1.0607074 0.00028975 8.39552E-08	(T _M - 20°($\begin{bmatrix} C \\ C \end{bmatrix} = (T_W - 20^{\circ}C)$ $\begin{bmatrix} Measurements No. \\ 1 \\ 2 \\ 3 \end{bmatrix}$	Position 1 0.5009 0.5013 0.5002	Position 2 0.5009 0.5013 0.5002	0.5009 0.5013
Length of measurement [mm] 0.75 Type Gauge block Measurement repetition name 6-11 6-11 6-11 6-11 9, (S,)*2 y, - y (y, - y)*2 Coverage factor (p) y U _{rep}	CTE [K*] 2.22E-05 Part number Calibration me Position 1 1.060306809 1.06037669 1.061084775 1.060307149 1.060533211 0.00032938 1.084918-07 -0.00032938 1.084918-07 -0.00036732 5.60421E-08 95.45	Object of calibration Uncertainty of CTE (u _{sw}) [K-1] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 1.0614 1.0609 1.0607 1.0608 1.0609 1.060943094 0.0028279 7.99702E-08 0.000173151 2.99812E-08	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 0.500000 Position 3 1.0604 1.0609 1.0612 1.0611 1.0609 1.06224154 8.65266E-08 0.000130784 1.71045E-08	U _{sabdison frem} 5.7735E-08 U _{sabdison frem} 0.000 Position 4 1.0607 1.0607 1.0612 1.0607 1.060707 1.060707 1.060707 1.0607074 0.00028975 8.39552E-08	(T _M - 20°(C) = (T _W - 20°C) Measurements No. 1 2 3 ELprop	Position 1 0.5009 0.5013 0.5002	Position 2 0.5009 0.5013	0.5009 0.5013
Length of measurement [mm] 0.75 Type Gauge block Measurement repetition name 6-11 6-11 6-11 6-11 9, (S,)*22 y,'-7 (y,'-y)*2 Coverage factor (p) y u _{rep} u _{geo}	CTE [K*] 2.22E-05 Part number Calibration me Position 1 1.060306809 1.06038652 1.06037669 1.061084775 1.060307149 1.060533211 0.00032938 1.0849127 -0.00036732 5.60421E-08 95.45 1.060769943	Object of calibration Uncertainty of CTE (u_sw) [K-1] 0.0000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions, 5 repeatitions each Position 2 1.0614 1.0609 1.0607 1.0608 1.0609 1.060943094 0.0028279 7.99702E-08 0.000173151 2.99812E-08		U _{sabdison frem} 5.7735E-08 U _{sabdison frem} 0.000 Position 4 1.0607 1.0607 1.0612 1.0607 1.060707 1.060707 1.060707 1.0607074 0.00028975 8.39552E-08	(T _M - 20°(C) = (T _W - 20°C) Measurements No. 1 2 3	Position 1 0.5009 0.5013 0.5002	Position 2 0.5009 0.5013 0.5002	0.5009 0.5013
Length of measurement [mm] 0.75 Type Gauge block Measurement repetition name 6-11 6-11 6-11 6-11 9, (S,)*2 y, - y (y, - y)*2 Coverage factor (p) y U _{rep}	CTE [K*] 2.22E-05 Part number Calibration me Position 1 1.060306809 1.06037669 1.061084775 1.060307149 1.060533211 0.00032938 1.084918-07 -0.00032938 1.084918-07 -0.00036732 5.60421E-08 95.45	Object of calibration Uncertainty of CTE (u_sw) [K-1] 0.0000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions, 5 repeatitions each Position 2 1.0614 1.0609 1.0607 1.0608 1.0609 1.060943094 0.0028279 7.99702E-08 0.000173151 2.99812E-08		U _{sabdison frem} 5.7735E-08 U _{sabdison frem} 0.000 Position 4 1.0607 1.0607 1.0612 1.0607 1.060707 1.060707 1.060707 1.0607074 0.00028975 8.39552E-08	(T _M - 20°(C) = (T _W - 20°C) Measurements No. 1 2 3 ELprop	Position 1 0.5009 0.5013 0.5002	Position 2 0.5009 0.5013 0.5002	0.5009 0.5013
Length of measurement [mm] 0.75 Type Gauge block Measurement repetition name 6-11 6-11 6-11 6-11 5, S, S, Y-2 y, -Y (y, - y)*2 Coverage factor (p) y U _{rop} U _{gro} E _L	CTE [K*] 2.22E-05 Part number Calibration me Position 1 1.060306809 1.06038652 1.06037669 1.061084775 1.060307149 1.060533211 0.00032938 1.0849127 -0.00036732 5.60421E-08 95.45 1.060769943	Object of calibration Uncertainty of CTE (u_sw) [K-1] 0.0000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions, 5 repeatitions each Position 2 1.0614 1.0609 1.0607 1.0608 1.0609 1.060943094 0.0028279 7.99702E-08 0.000173151 2.99812E-08		U _{sabdison frem} 5.7735E-08 U _{sabdison frem} 0.000 Position 4 1.0607 1.0607 1.0612 1.0607 1.060707 1.060707 1.060707 1.0607074 0.00028975 8.39552E-08	(T _M - 20°(C) = (T _W - 20°C) Measurements No. 1 2 3 ELprop	Position 1 0.5009 0.5013 0.5002	Position 2 0.5009 0.5013 0.5002	0.5009 0.5013
Length of measurement [mm] 0.75 Type Gauge block Measurement repetition name 6-11 6-11 6-11 6-11 9, (S,)*22 y,'-7 (y,'-y)*2 Coverage factor (p) y u _{rep} u _{geo}	CTE [K¹] 2.22E-05 Part number Calibration me Position 1 1.060306809 1.060589652 1.060377669 1.061084775 1.060307149 1.060533211 0.00022938 1.08491E-07 -0.000236732 5.60421E-08 95.45 1.060769943 0.000299559 9.47118E-05	Object of calibration Uncertainty of CTE (u _{sw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 assurments: 4 positions, 5 repeatitions each Position 2 1.0614 1.0609 1.0607 1.0608 1.0609 1.060943094 0.00028279 7.99702E-08 0.000173151 2.99812E-08	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 0.500000 Position 3 1.0604 1.0609 1.0612 1.0611 1.0609 1.00300727 0.000294154 8.65266E-08 0.000130764 1.71045E-08	U _{sabdison frem} 5.7735E-08 U _{sabdison frem} 0.000 Position 4 1.0607 1.0607 1.0612 1.0607 1.060707 1.060707 1.060707 1.0607074 0.00028975 8.39552E-08	(T _M - 20°(C) = (T _W - 20°C) Measurements No. 1 2 3 ELprop	Position 1 0.5009 0.5013 0.5002	Position 2 0.5009 0.5013 0.5002	0.5009 0.5013

	OTE IIII	Object of calibration	(2 . 2) 57723		/TE 200]			
gth of measurement [mm] 0.75	CTE [K-1] 2.22E-05	Uncertainty of CTE (u _{aW}) [K ⁻¹] 0.00000069	$(u^2_{TW} + u^2_{TWS}) [K^2]$ 0.003333333	u _{aM} 5.7735E-08	$(1_{\rm M} - 20^{\circ})$	C) = (T _w – 20°C)			
0.70	2.222 00	0.0000000	0.00000000	0.17002 00	0.0	J			
-		Reference artefact used				1			
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
ige block	-	0.75	0.500000	0.0001	1 2	1			
	Calibration mas	asurments: 4 positions, 5 repeatitions each			-		Course block massure	romont	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	+	Measurements No.	Gauge block measur Position 1	Position 2	Position 3
16	1.060023967	1.0607	1.0600	1.0592	1	1	0.5009		0.5009
16	1.060589652	1.0615	1.0596	1.0590		2	0.5013		0.5013
16 16	1.060094571 1.059740935	1.0619 1.0616	1.0592 1.0592	1.0588 1.0596		3	0.5002	2 0.5002	0.5002
16	1.059528886	1.0611	1.0594	1.0587					
y _j S _i	1.059995602	1.061339777	1.05947233	1.059062372	1				
S _j (S _j)^2	0.000401925 1.61543E-07	0.00047041 2.21285E-07	0.000313907 9.85374E-08	0.000366063 1.34002E-07					
y _i - y	2.80821E-05	0.001372257	-0.000495191	-0.000905149					
(y _j - y)^2	7.88602E-10	1.88309E-06	2.45214E-07	8.19294E-07	_				
Coverage factor (p)	95.45	%							
у	1.05996752					E _{Lprop}	0.0016	٦	
у	1.03990732					Lprop	0.0010	_	
		Degree of freedom (ve)	u_e^4/v_e					_	
U _{rep}	0.000392227	16	5.91685E-17			L _{measstd}	0.5008	Degree of freedom	
u_{geo}	0.00049568	3	1.25767E-15			U _{measstd}	0.000482183	8	
	0.0012						•	•	
EL	0.0012								
Ucorr	0.000252488	9	4.51562E-16						
U _{temp}	9.95739E-07	∞	0						
F			Ī						
Calibrated value	1.058767520		Effective degree of freedom	13	٦				
					_				
standard uncertainty	0.000394898								
k factor	2.211800697								
	0.000070405								
Extended uncertainty	0.000873435								
		CALCULATION	OF LENCTI	I CAI IDI) ATI	ON			
		CALCULATION	OF LEMOTI	I CALIDI	MII.	O11			
		Object of calibration]			
gth of measurement [mm]	CTE [K-1]	Uncertainty of CTE $(u_{\alpha W})$ [K ⁻¹]	$(u^2_{TW} + u^2_{TWS})[K^2]$	$\mathbf{u}_{a\mathrm{M}}$		CC) = (T _w - 20°C)			
gth of measurement [mm] 0.75	CTE [K-1] 2.22E-05		$(u^2_{TW} + u^2_{TWS})[K^2]$ 0.0033333333	u _{eM} 5.7735E-08	(T _M - 20°] PC) = (T _W - 20°C)			
		Uncertainty of CTE (u _{aW}) [K ⁻¹] 0.00000069				C) = (T _w - 20°C)			
0.75	2.22E-05	Uncertainty of CTE (u_{aw}) $[K^{-1}]$ 0.00000069 Reference artefact used	0.003333333	5.7735E-08	0.5] CC) = (T _w – 20°C)			
		Uncertainty of CTE (u _{aW}) [K ⁻¹] 0.00000069	0.003333333 Calibrated length /mm		0.5]			
0.75	2.22E-05	Uncertainty of CTE (u_{aW}) $[K^{-1}]$ 0.00000069 Reference artefact used Nominal length /mm	0.003333333 Calibrated length /mm	5.7735E-08 U calibration /mm	0.5]			
0.75 Type ige block	2.22E-05 Part number - Calibration mea	Uncertainty of CTE (u _{sw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each	0.003333333 Calibrated length /mm 0.500000	5.7735E-08 Ucalibration /mm 0.000	0.5		Gauge block measu	rement	
0.75 Type ige block Measurement repetition name	2.22E-05 Part number Calibration mee Position 1	Uncertainty of CTE (u _{sw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2	Calibrated length /mm 0.500000	5.7735E-08 Ucalibration /mm 0.000	0.5	Measurements No.	Position 1	Position 2	Position 3
0.75 Type ige block Measurement repetition name 21	2.22E-05 Part number Calibration med Position 1 1.061013728	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 1.0613	0.003333333 Calibrated length /mm 0.500000 Position 3 1.0626	5.7735E-08 Ucationalism 0.0000	0.5	Measurements No.	Position 1 0.500	Position 2 9 0.5009	0.5009
0.75 Type ige block Measurement repetition name	2.22E-05 Part number Calibration mee Position 1	Uncertainty of CTE (u _{sw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2	Calibrated length /mm 0.500000	5.7735E-08 Ucalibration /mm 0.000	0.5	Measurements No.	Position 1	Position 2 9 0.5009 3 0.5013	
0.75 Type ige block Measurement repetition name 21 21 21 21	2.22E-05 Part number Calibration mee Position 1 1.061013728 1.060094486 1.06030664 1.060801744	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 1.0613 1.0605 1.0604	0.003333333 Calibrated length /mm 0.500000 Position 3 1.0626 1.0623 1.0624 1.0621	Ucalibration Imm 0.000 Position 4 1.0617 1.0623 1.0619 1.0615	0.5	Measurements No.	Position 1 0.500 0.501	Position 2 9 0.5009 3 0.5013	0.5009 0.5013
Type ige block Measurement repetition name 21 21 21 21 21 21	2.22E-05 Part number Calibration med Position 1 1.061013728 1.060904486 1.06030664 1.060801744 1.060872325	Uncertainty of CTE (u _{sw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 1.0613 1.0604 1.0604 1.0612	Calibrated length /mm 0.500000 Position 3 1.0626 1.0623 1.0624 1.0621 1.0621	5.7735E-08 U_calibration /mm 0.000 Position 4 1.0617 1.0623 1.0619 1.0615 1.0622	0.5	Measurements No.	Position 1 0.500 0.501	Position 2 9 0.5009 3 0.5013	0.5009 0.5013
Type ige block Measurement repetition name 21 21 21 21 21 21 31 5	2.22E-05 Part number Calibration mes Position 1 1.061013728 1.06094486 1.06094486 1.060801744 1.060872325 1.060817784 0.000395618	Uncertainty of CTE (u _{sw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 1.0613 1.0605 1.0604 1.0612 1.060773528 0.000449114	Calibrated length /mm 0.500000 Position 3 1.0626 1.0623 1.0624 1.0621 1.0621 1.0621 1.062300676 0.000220236	U_calibration imm	0.5	Measurements No.	Position 1 0.500 0.501	Position 2 9 0.5009 3 0.5013	0.5009 0.5013
0.75 Type Ige block Measurement repetition name 21 21 21 21 21 21 (S),(S),(Y2	2.22E-05 Part number Calibration mee Position 1 1.061013728 1.060094486 1.06030664 1.060801744 1.060872325 1.060617784 0.000396618 1.56514E-07	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 1.06013 1.0605 1.0604 1.0604 1.0604 1.0604 1.0604 2.1060773528 0.000449114 2.01704E-07	Calibrated length /mm 0.500000 Position 3 1.0626 1.0623 1.0624 1.0621 1.0621 1.0626 0.000220236 4.85039E-08	5.7735E-08 Ucalibration Imm 0.000 Position 4 1.0617 1.0623 1.0619 1.0615 1.0622 1.061918927 0.000329384 1.08494E-07	0.5	Measurements No.	Position 1 0.500 0.501	Position 2 9 0.5009 3 0.5013	0.5009 0.5013
Type Ige block Measurement repetition name 21 21 21 21 21 21 21 31 (S.)/2 y, - y	2.22E-05 Part number Calibration mes Position 1 1.061013728 1.06094486 1.06094486 1.060801744 1.060872325 1.060817784 0.000395618	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 1.06013 1.0605 1.0604 1.0604 1.0604 1.0604 1.0604 2.1060773528 0.000449114 2.01704E-07	Calibrated length /mm 0.500000 Position 3 1.0626 1.0623 1.0624 1.0621 1.0621 1.0621 1.062300676 0.000220236	U_calibration imm	0.5	Measurements No.	Position 1 0.500 0.501	Position 2 9 0.5009 3 0.5013	0.5009 0.5013
0.75 Type Ige block Measurement repetition name 21 21 21 21 21 31 51 (S)/22 1/- 1/- 2 1/- 2 1/- 2 1/- 2 1/-	2.22E-05 Part number Calibration mea Position 1 1.061013728 1.060904486 1.060801744 1.060872325 1.060877784 0.000396618 1.56514E-07 -0.000784944 6.16138E-07	Uncertainty of CTE (u _{sw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 1.0613 1.0605 1.0604 1.0612 1.060773528 0.00049114 2.01704E-07 -0.0006292 3.95893E-07	Calibrated length /mm 0.500000 Position 3 1.0626 1.0623 1.0624 1.0621 1.0621 1.0621 1.0620 6.000220236 4.85039E-08 0.000897947	Ucalibration intern 0.000 Position 4 1.0617 1.0623 1.0619 1.0615 1.0622 1.0619827 0.000329384 1.08494E-07 0.000516198	0.5	Measurements No.	Position 1 0.500 0.501	Position 2 9 0.5009 3 0.5013	0.5009 0.5013
Type Ige block Measurement repetition name 21 21 21 21 21 21 21 31 (S.)/2 y, - y	2.22E-05 Part number Calibration mea Position 1 1.061013728 1.060904486 1.060801744 1.060872325 1.060877784 0.000396618 1.56514E-07 -0.000784944	Uncertainty of CTE (u _{sw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 1.0613 1.0605 1.0604 1.0612 1.060773528 0.00049114 2.01704E-07 -0.0006292 3.95893E-07	Calibrated length /mm 0.500000 Position 3 1.0626 1.0623 1.0624 1.0621 1.0621 1.0621 1.0620 6.000220236 4.85039E-08 0.000897947	Ucalibration intern 0.000 Position 4 1.0617 1.0623 1.0619 1.0615 1.0622 1.0619827 0.000329384 1.08494E-07 0.000516198	0.5	Measurements No.	Position 1 0.500 0.501	Position 2 9 0.5009 3 0.5013	0.5009 0.5013
0.75 Type Ige block Measurement repetition name 21 21 21 21 21 31 51 (S)/22 1/- 1/- 2 1/- 2 1/- 2 1/- 2 1/-	2.22E-05 Part number Calibration mea Position 1 1.061013728 1.060904486 1.060801744 1.060872325 1.060877784 0.000396618 1.56514E-07 -0.000784944 6.16138E-07	Uncertainty of CTE (u _{sw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 1.0613 1.0605 1.0604 1.0612 1.060773528 0.00049114 2.01704E-07 -0.0006292 3.95893E-07	Calibrated length /mm 0.500000 Position 3 1.0626 1.0623 1.0624 1.0621 1.0621 1.0621 1.0620 6.000220236 4.85039E-08 0.000897947	Ucalibration intern 0.000 Position 4 1.0617 1.0623 1.0619 1.0615 1.0622 1.0619827 0.000329384 1.08494E-07 0.000516198	0.5	Measurements No.	Position 1 0.500 0.501	Position 2 9 0.5009 3 0.5013	0.5009 0.5013
0.75 Type ige block Measurement repetition name 21 21 21 21 21 21 (S) (S)/2 (y) - y (yj - y)/2 Coverage factor (p)	2.22E-05 Part number Calibration mes Position 1 1.061013728 1.060094486 1.06030664 1.060801744 1.060872325 1.060017784 0.000395618 1.56514E-07 -0.000784944 6.16138E-07	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 1.0613 1.0605 1.0604 1.0604 1.0604 1.0604 1.06073528 0.000449114 2.01704E-07 - 0.0006292 3.95893E-07	Calibrated length /mm 0.500000 Position 3 1.0626 1.0623 1.0624 1.0621 1.0621 1.062300676 0.000220236 4.85039E-08 0.000897947 8.06308E-07	Ucalibration intern 0.000 Position 4 1.0617 1.0623 1.0619 1.0615 1.0622 1.0619827 0.000329384 1.08494E-07 0.000516198	0.5	Measurements No. 1 2 3	Position 1 0.500 0.501 0.500	Position 2 9 0.5009 3 0.5013	0.5009 0.5013
0.75 Type Ige block Measurement repetition name 21 21 21 21 21 21 21 21 21 21 21 21 21	2.22E-05 Part number Calibration mes Position 1 1.061013728 1.060094486 1.06030664 1.060801744 1.060872325 1.060017784 0.000395618 1.56514E-07 -0.000784944 6.16138E-07	Uncertainty of CTE (u _{sw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 1.0613 1.0605 1.0604 1.0612 1.060773528 0.00049114 2.01704E-07 -0.0006292 3.95893E-07	Calibrated length /mm 0.500000 Position 3 1.0626 1.0623 1.0624 1.0621 1.0621 1.0621 1.0620 6.000220236 4.85039E-08 0.000897947	Ucalibration intern 0.000 Position 4 1.0617 1.0623 1.0619 1.0615 1.0622 1.0619827 0.000329384 1.08494E-07 0.000516198	0.5	Measurements No. 1 2 3	Position 1 0.500 0.501 0.500	Position 2 9 0.5009 3 0.5013 2 0.5002	0.5009 0.5013
Type Ige block Measurement repetition name 21 21 21 21 Y; S; (S)/22 Y;-Y)*2 Coverage factor (p) y U _{rep}	2.22E-05 Part number Calibration mea Position 1 1.061013728 1.06094486 1.060904486 1.060801744 1.060872325 1.060617784 0.000395618 1.56514E-07 -0.000784944 6.16138E-07 95.45 1.061402729	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 1.0613 1.0605 1.0604 1.0604 1.0604 1.0604 1.06073528 0.000449114 2.01704E-07 -0.0006292 3.95893E-07 % Degree of freedom (v _e)	Calibrated length /mm 0.500000 Position 3 1.0626 1.0623 1.0624 1.0621 1.0621 1.0621 1.0622 1.0624 1.0627 1.0627 1.0627 1.0628 0.000220236 4.85039E-08 0.000897947 8.06308E-07	Ucalibration intern 0.000 Position 4 1.0617 1.0623 1.0619 1.0615 1.0622 1.0619827 0.000329384 1.08494E-07 0.000516198	0.5	Measurements No. 1 2 3 Etyrop Lineastid	Position 1 0.500 0.501 0.500 0.501 0.500	Position 2 9 0.5009 3 0.5013 2 0.5002 Degree of freedom	0.5009 0.5013
Type Ige block Measurement repetition name 21 21 21 21 21 21 21 Yi Si Si (Si)''22 Yi - Y (Yi - Y)''2 Coverage factor (p) y u _{rep} u _{geo}	2.22E-05 Part number Calibration mer Position 1 1.061013728 1.06094486 1.06030664 1.060801744 1.060872325 1.060617784 0.000395618 1.56514E-07 -0.000784944 6.16138E-07 1.061402729 0.000358892 0.000416813	Uncertainty of CTE (u _{sw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 1.0613 1.0605 1.0604 1.0612 1.06073528 0.000449114 2.01704E-07 -0.0006292 3.95893E-07	Calibrated length /mm 0.500000 Position 3 1.0626 1.0623 1.0624 1.0621 1.0621 1.0621 1.0626 0.000220236 4.85039E-08 0.000897947 8.06308E-07	Ucalibration intern 0.000 Position 4 1.0617 1.0623 1.0619 1.0615 1.0622 1.0619827 0.000329384 1.08494E-07 0.000516198	0.5	Measurements No. 1 2 3	Position 1 0.500 0.501 0.500 0.501 0.500	Position 2 9 0.5009 3 0.5013 2 0.5002	0.5009 0.5013
Type Ige block Measurement repetition name 21 21 21 21 Y; S; (S)/22 Y;-Y)*2 Coverage factor (p) y U _{rep}	2.22E-05 Part number Calibration mea Position 1 1.061013728 1.06094486 1.060904486 1.060801744 1.060872325 1.060617784 0.000395618 1.56514E-07 -0.000784944 6.16138E-07 95.45 1.061402729	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 1.0613 1.0605 1.0604 1.0604 1.0604 1.0604 1.06073528 0.000449114 2.01704E-07 -0.0006292 3.95893E-07 % Degree of freedom (v _e)	Calibrated length /mm 0.500000 Position 3 1.0626 1.0623 1.0624 1.0621 1.0621 1.0621 1.0622 1.0624 1.0627 1.0627 1.0627 1.0628 0.000220236 4.85039E-08 0.000897947 8.06308E-07	Ucalibration intern 0.000 Position 4 1.0617 1.0623 1.0619 1.0615 1.0622 1.0619827 0.000329384 1.08494E-07 0.000516198	0.5	Measurements No. 1 2 3 Etyrop Lineastid	Position 1 0.500 0.501 0.500 0.501 0.500	Position 2 9 0.5009 3 0.5013 2 0.5002 Degree of freedom	0.5009 0.5013
Type Ige block Measurement repetition name 21 21 21 21 21 21 21 Yi Si Si (Si)''22 Yi - Y (Yi - Y)''2 Coverage factor (p) y u _{rep} u _{geo}	2.22E-05 Part number Calibration mer Position 1 1.061013728 1.06094486 1.06030664 1.060801744 1.060872325 1.060617784 0.000395618 1.56514E-07 -0.000784944 6.16138E-07 1.061402729 0.000358892 0.000416813	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 1.0613 1.0605 1.0604 1.0604 1.0604 1.0604 1.06073528 0.000449114 2.01704E-07 -0.0006292 3.95893E-07 % Degree of freedom (v _e)	Calibrated length /mm 0.500000 Position 3 1.0626 1.0623 1.0624 1.0621 1.0621 1.0621 1.0622 1.0624 1.0627 1.0627 1.0627 1.0628 0.000220236 4.85039E-08 0.000897947 8.06308E-07	Ucalibration intern 0.000 Position 4 1.0617 1.0623 1.0619 1.0615 1.0622 1.0619827 0.000329384 1.08494E-07 0.000516198	0.5	Measurements No. 1 2 3 Etyrop Lineastid	Position 1 0.500 0.501 0.500 0.501 0.500	Position 2 9 0.5009 3 0.5013 2 0.5002 Degree of freedom	0.5009 0.5013
Type Ige block Measurement repetition name 21 21 21 21 21 21 21 Vi S, (S,)/22 (Y,- y/^2) Coverage factor (p) y U _{mp} U _{geo} E _L U _{corr}	2.22E-05 Part number Calibration mer Position 1 1.061013728 1.060904486 1.060904486 1.060801744 1.060872325 1.06081748 0.000395618 1.56514E-07 -0.000784944 6.16138E-07 95.45 1.061402729 0.000358892 0.000416813 0.0012	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 1.0613 1.0605 1.0604 1.0604 1.0604 1.06012 1.060773528 0.000449114 2.01704E-07 - 0.0006292 3.95893E-07 % Degree of freedom (v _e) 16 3	Calibrated length /mm 0.500000 Position 3 1.0626 1.0623 1.0624 1.0621 1.0621 1.062300676 0.000220236 4.85039E-08 0.000897947 8.06308E-07	Ucalibration intern 0.000 Position 4 1.0617 1.0623 1.0619 1.0615 1.0622 1.0619827 0.000329384 1.08494E-07 0.000516198	0.5	Measurements No. 1 2 3 Etyrop Lineastid	Position 1 0.500 0.501 0.500 0.501 0.500	Position 2 9 0.5009 3 0.5013 2 0.5002 Degree of freedom	0.5009 0.5013
Type Ige block Measurement repetition name 21 21 21 21 21 21 21 21 21 21 21 21 21	2.22E-05 Part number Calibration mer Position 1 1.061013728 1.060094486 1.06030664 1.060801744 1.060872325 1.060817784 0.000398618 1.56514E-07 -0.000784944 6.16138E-07 1.061402729 0.000356892 0.000416813 0.0012	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 1.0613 1.0605 1.0604 1.0604 1.0604 1.0604 2.01704E-07 -0.0006292 3.95893E-07 % Degree of freedom (v _e) 16 3	Calibrated length /mm 0.500000 Position 3 1.0626 1.0623 1.0624 1.0621 1.0621 1.062300676 0.000220236 4.85039E-08 0.000897947 8.06308E-07 u_e^4/v_e 4.1476E-17 6.28818E-16	Ucalibration intern 0.000 Position 4 1.0617 1.0623 1.0619 1.0615 1.0622 1.0619827 0.000329384 1.08494E-07 0.000516198	0.5	Measurements No. 1 2 3 Etyrop Lineastid	Position 1 0.500 0.501 0.500 0.501 0.500	Position 2 9 0.5009 3 0.5013 2 0.5002 Degree of freedom	0.5009 0.5013
Type Ige block Measurement repetition name 21 21 21 21 S, (S,)''2 y, - y (y, - y)''2 Coverage factor (p) y U _{mpp} U _{geo} E _L U _{temp}	2.22E-05 Part number Calibration mea Position 1 1.061013728 1.06094486 1.060904486 1.060801744 1.060872325 1.060817784 0.000395618 1.56514E-07 -0.000784944 6.16138E-07 95.45 1.061402729 0.000358892 0.000416813 0.0012 0.000252488	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 1.0613 1.0605 1.0604 1.0604 1.0604 1.06012 1.060773528 0.000449114 2.01704E-07 - 0.0006292 3.95893E-07 % Degree of freedom (v _e) 16 3	Calibrated length /mm 0.500000 Position 3 1.0626 1.0623 1.0624 1.0621 1.0621 1.0622 1.0622 1.0624 1.0627 1.0627 1.0627 1.0628 1.0628 1.0628 1.0628 1.0628 1.0628 1.0629 1.06299947 1.06290897947 1.0629897947 1.0628818E-16	5.7735E-08 Ucalibration //mm 0.000 Position 4 1.0617 1.0623 1.0619 1.0615 1.0622 1.061918927 0.000329384 1.08494E-07 0.000516198 2.6646E-07	0.5	Measurements No. 1 2 3 Etyrop Lineastid	Position 1 0.500 0.501 0.500 0.501 0.500	Position 2 9 0.5009 3 0.5013 2 0.5002 Degree of freedom	0.5009 0.5013
Type Ige block Measurement repetition name 21 21 21 21 21 21 21 Vi S, (S,)/22 (Y,- y/^2) Coverage factor (p) y U _{mp} U _{geo} E _L U _{corr}	2.22E-05 Part number Calibration mer Position 1 1.061013728 1.060904486 1.060904486 1.060801744 1.060872325 1.06081748 0.000395618 1.56514E-07 -0.000784944 6.16138E-07 95.45 1.061402729 0.000358892 0.000416813 0.0012	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 1.0613 1.0605 1.0604 1.0604 1.0604 1.06012 1.060773528 0.000449114 2.01704E-07 - 0.0006292 3.95893E-07 % Degree of freedom (v _e) 16 3	Calibrated length /mm 0.500000 Position 3 1.0626 1.0623 1.0624 1.0621 1.0621 1.062300676 0.000220236 4.85039E-08 0.000897947 8.06308E-07	Ucalibration intern 0.000 Position 4 1.0617 1.0623 1.0619 1.0615 1.0622 1.0619827 0.000329384 1.08494E-07 0.000516198	0.5	Measurements No. 1 2 3 Etyrop Lineastid	Position 1 0.500 0.501 0.500 0.501 0.500	Position 2 9 0.5009 3 0.5013 2 0.5002 Degree of freedom	0.5009 0.5013
Type Ige block Measurement repetition name 21 21 21 21 S, (S,)''2 y, - y (y, - y)''2 Coverage factor (p) y U _{mpp} U _{geo} E _L U _{temp}	2.22E-05 Part number Calibration mea Position 1 1.061013728 1.06094486 1.060904486 1.060801744 1.060872325 1.060817784 0.000395618 1.56514E-07 -0.000784944 6.16138E-07 95.45 1.061402729 0.000358892 0.000416813 0.0012 0.000252488	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 1.06013 1.0605 1.0604 1.0604 1.0604 1.06012 1.060773528 0.000449114 2.01704E-07 - 0.0006292 3.95893E-07 % Degree of freedom (v _e) 16 3	Calibrated length /mm 0.500000 Position 3 1.0626 1.0623 1.0624 1.0621 1.0621 1.0622 1.0622 1.0624 1.0627 1.0627 1.0627 1.0628 1.0628 1.0628 1.0628 1.0628 1.0628 1.0629 1.06299947 1.06290897947 1.0629897947 1.0628818E-16	5.7735E-08 Ucalibration //mm 0.000 Position 4 1.0617 1.0623 1.0619 1.0615 1.0622 1.061918927 0.000329384 1.08494E-07 0.000516198 2.6646E-07	0.5	Measurements No. 1 2 3 Etyrop Lineastid	Position 1 0.500 0.501 0.500 0.501 0.500	Position 2 9 0.5009 3 0.5013 2 0.5002 Degree of freedom	0.5009 0.5013
Type Ige block Measurement repetition name 21 21 21 21 21 21 Vi Si (S)/Y2 VjY/Y2 Coverage factor (p) y Umap Ugano EL Usorr Utemp Calibrated value standard uncertainty	2.22E-05 Part number Calibration met Position 1 1.061013728 1.06094486 1.06094486 1.060801744 1.060872325 1.060817784 0.000395618 1.56514E-07 -0.000784944 6.16138E-07 95.45 1.061402729 0.000358892 0.000416813 0.0012 0.000252488 9.95739E-07	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 1.06013 1.0605 1.0604 1.0604 1.0604 1.06012 1.060773528 0.000449114 2.01704E-07 - 0.0006292 3.95893E-07 % Degree of freedom (v _e) 16 3	Calibrated length /mm 0.500000 Position 3 1.0626 1.0623 1.0624 1.0621 1.0621 1.0622 1.0622 1.0624 1.0627 1.0627 1.0627 1.0628 1.0628 1.0628 1.0628 1.0628 1.0628 1.0629 1.06299947 1.06290897947 1.0629897947 1.0628818E-16	5.7735E-08 Ucalibration //mm 0.000 Position 4 1.0617 1.0623 1.0619 1.0615 1.0622 1.061918927 0.000329384 1.08494E-07 0.000516198 2.6646E-07	0.5	Measurements No. 1 2 3 Etyrop Lineastid	Position 1 0.500 0.501 0.500 0.501 0.500	Position 2 9 0.5009 3 0.5013 2 0.5002 Degree of freedom	0.5009 0.5013
Type Ige block Measurement repetition name 21 21 21 21 Y; S; (S;)'22 Y;-Y'2 Coverage factor (p) y U _{resp} U _{geno} EL U _{corr} U _{temp} Calibrated value	2.22E-05 Part number Calibration mer Position 1 1.061013728 1.060904486 1.060904486 1.060801744 1.0608272325 1.060617784 0.000395618 1.56514E-07 -0.000784944 6.16138E-07 95.45] 1.061402729 0.000358892 0.000416813 0.0012 0.000252488 9.95739E-07	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 0.75 asurments: 4 positions, 5 repeatitions each Position 2 1.06013 1.0605 1.0604 1.0604 1.0604 1.06012 1.060773528 0.000449114 2.01704E-07 - 0.0006292 3.95893E-07 % Degree of freedom (v _e) 16 3	Calibrated length /mm 0.500000 Position 3 1.0626 1.0623 1.0624 1.0621 1.0621 1.0622 1.0622 1.0624 1.0627 1.0627 1.0627 1.0628 1.0628 1.0628 1.0628 1.0628 1.0628 1.0629 1.06299947 1.06290897947 1.0629897947 1.0628818E-16	5.7735E-08 Ucalibration //mm 0.000 Position 4 1.0617 1.0623 1.0619 1.0615 1.0622 1.061918927 0.000329384 1.08494E-07 0.000516198 2.6646E-07	0.5	Measurements No. 1 2 3 Etyrop Lineastid	Position 1 0.500 0.501 0.500 0.501 0.500	Position 2 9 0.5009 3 0.5013 2 0.5002 Degree of freedom	0.5009 0.5013

9.95739E-07

0.000305284

Calibrated value standard uncertainty

k factor

Extended uncertainty

CALCULATION OF LENGTH CALIBRATION

		Object of calibration				1			
ength of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{aW}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS})[K^2]$	u_{aM}	(T _M - 20°	$(C) = (T_W - 20^{\circ}C)$			
0.75	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5	ĺ . "			
		Reference artefact used				1			
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
auge block	-	0.75	0.500000	0.0001	2				
	Calibration me	asurments: 4 positions, 5 repeatitions each			1		Gauge block measuremer	ıt	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	1	Measurements No.	Position 1	Position 2	Position 3
1-26	1.060660257	1.0591	1.0587	1.0607	İ	1	0.5009	0.5009	0.5009
1-26	1.061225895	1.0601	1.0595	1.0603		2	0.5013	0.5013	0.5013
1-26	1.061084587	1.0600	1.0595	1.0607		3	0.5002	0.5002	0.5002
1-26	1.060872702	1.0597	1.0592	1.0612					
1-26	1.06129657	1.0595	1.0602	1.0607					
	1.061028002	1.05969856	1.059429814	1.060730941	1				
y _i S _i	0.000261652	0.000401842	0.000537585	0.00029998					
(S _j)^2	6.84618E-08	1.61477E-07	2.88997E-07	8.9988E-08					
y _i - y (y _i - y)^2	0.000806173 6.49914E-07	-0.000523269 2.73811E-07	-0.000792015 6.27288E-07	0.000509112 2.59195E-07					
(y ₁ - y) 2	0.45914E-07	2.73011E=07	0.27200L=07	2.39193E=01	1				
Coverage factor (p)	95.45	%							
						_			
У	1.060221829					E _{Lprop}	0.0016		
		Degree of freedom (v _e)	n 4/n						
	0.000300469	16	u _e ⁴ /v _e				0.5008		
U _{rep}	0.000390168	10	5.79357E-17			Lmeasstd	0.5008	gree of freedom	
Ugeo	0.000388395	3	4.74082E-16			U _{measstd}	0.000482183	8	
E∟	0.0012								
	0.000252488	9	4 545605 46						
Ucorr	0.000252488	9	4.51562E-16						
U _{temp}	9.95739E-07	00	0						
					,				
Calibrated value	1.059021829		Effective degree of freedom	17]				
standard uncertainty	0.000363194								
Standard uncertainty	0.00000104								
k factor	2.158263401								
Extended uncertainty	0.000783868								
				_ ~					
		CALCULATION	OF LENGT	H CALIBE	RATI(ON			
		01: 1.6				_			
	CTE [K-1]	Object of calibration	(2 , 2) frz21		(T. 20)				
ength of measurement [mm]		Uncertainty of CTE (uaW) [K-1]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	u _{aM}		$^{\circ}C) = (T_{W} - 20^{\circ}C)$			
0.75	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5				
		Reference artefact used							
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
auge block	-	0.75	0.500000	0.0001	1 2	2]			
		easurments: 4 positions, 5 repeatitions each					Gauge block measureme		
Measurement repetition name	Position 1	Position 2	Position 3	Position 4		Measurements No.	Position 1	Position 2	Position 3
6-31	1.060448	1.061650	1.062075	1.060872		1	0.5009	0.5009	0.5009
8-31	1.060872	1.060731	1.061226	1.061156		2	0.5013	0.5013	0.5013
6-31	1.060802	1.061297	1.061297	1.061084		3	0.5002	0.5002	0.5002
6-31	1.060731	1.061438	1.062145	1.060731					
6-31	1.060660	1.061509	1.061650	1.061085					
y _j S _i	1.060702766 0.000162824	1.061325138 0.000355703	1.061678501 0.000426046	1.06098567 0.000177536					
(S _i)^2	2.65117E-08	1.26525E-07	1.81515E-07	3.15189E-08	1				
	-0.000470253	0.000152119	0.000505482	-0.000187348	1				
y _i - y (y _i - y)^2	2.21138E-07	2.31403E-08	2.55512E-07	3.50994E-08	╛				
	05.45								
Coverage factor (p)	95.45	70							
у	1.061173019	1				E _{Lprop}	0.0016		
,		•				prop			
		Degree of freedom (v _e)	u_e^4/ν_e						
U _{rep}	0.000302519	16	2.09387E-17			L _{measstd}	0.5008		
	0.0005		4.4005				D	egree of freedom	
U _{geo}	0.000211126	3	4.13928E-17			U _{measstd}	0.000482183	8	
E∟	0.0012	1							
Ucorr	0.000252488	9	4.51562E-16						

Calibrated value

standard uncertainty k factor Extended uncertainty

CALCULATION OF LENGTH CALIBRATION

Length of measurement [mm]	CTE [K-1]	Object of calibration Uncertainty of CTE (u _{aW}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS})[K^2]$		(T 20°	$T(C) = (T_W - 20^{\circ}C)$		
0.75	2.22E-05	0.00000069	0.003333333	u _{αM} 5.7735E-08	0.5] - (1 _W - 20 C)		
	<u>'</u>			•		-		
		Reference artefact used				1		
Type	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k			
Gauge block	-	0.75	0.500000	0.000	11 2			
	O-lib-refire				_		On the blook management	
Measurement repetition name	Position 1	easurments: 4 positions, 5 repeatitions each Position 2	Position 3	Position 4	\dashv	Measurements No.	Gauge block measurement Position 1 Position 2	Position 3
15-16	0.751000	0.749001	0.751800	0.750700		1	0.5009 0.5009	0.5009
15-16	0.751000	0.749400 0.749400	0.751500	0.750501		2	0.5013 0.5013	0.5013
15-16 15-16	0.750900 0.750600	0.749400	0.752000 0.751600	0.751300 0.750900		3	0.5002 0.5002	0.5002
15-16	0.750901	0.749300	0.751900	0.751700				
y _i S _i	0.750880429	0.749160403	0.751760045 0.000207357	0.75102028				
(S ₁)^2	0.000164253 2.6979E-08	0.000304868 9.29442E-08	4.29969E-08	0.00048136 2.31708E-07				
y _i - y	0.00011014	-0.001544886	0.001054756	0.000314991				
(y _j - y)^2	3.06739E-08	2.38667E-06	1.11251E-06	9.9219E-08				
Coverage factor (p)	95.45]%						
у	0.750705289	1				E _{Lprop}	0.0016	
,			4.					
	0.000314097	Degree of freedom (v _c) 16	u _e ⁴ / v _e 2.4333E-17			1	0.5008	
U _{rep}	0.000314097] 16	2.4333⊑-17			Lmeasstd	Degree of freedom	
U _{geo}	0.00054993	3	1.90541E-15			U _{measstd}	0.000482183 8	
EL	0.0012	1						
		- 1 9	4.545005.40					
Ucorr	0.000252488] a	4.51562E-16					
U _{temp}	9.95739E-07	_ ∞	0					
Calibrated value	0.749505289]	Effective degree of freedom	10				
standard uncertainty	0.000398859	1						
Standard uncertainty	0.000330033	,						
k factor	2.283681613							
Extended uncertainty	0.000910866	1						
		1						
		CALCULATION	OF LENGTE	I CALIBI	RATIC)N		
	CTE [K-1]	Object of calibration	(-2 + -2) FV ² 1		/T 200	T) = (T 20%C)		
ength of measurement [mm] 0.75	2.22E-05	Uncertainty of CTE (u _{aW}) [K ⁻¹] 0.00000069	$(u^2_{TW} + u^2_{TWS}) [K^2]$ 0.003333333	u _{αM} 5.7735E-08	0.5	$(T_{w} - 20^{\circ}C)$		
					1			
		Reference artefact used						
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k			
Sauge block	-	0.75	0.500000	0.000	1 2			
					_			
Measurement repetition name	Calibration mea	asurments: 4 positions, 5 repeatitions each Position 2	Position 3	Position 4		Measurements No.	Gauge block measurement Position 1 Position 2	Position 3
5-21	0.749500	0.750100	0.751500	0.749800		1	0.5009 0.5009	0.5009
5-21	0.749601	0.749900	0.751200	0.750300		2	0.5013 0.5013	0.5013
5-21	0.749401 0.749701	0.749400 0.749401	0.751100 0.751500	0.750300 0.749900		3	0.5002 0.5002	0.5002
5-21 5-21	0.749001	0.750100	0.750600	0.750600				
y _i S _i	0.749440789	0.749780215	0.751180222	0.750180039				
S _j (S _j)^2	0.000270271 7.30463E-08	0.000356329 1.26971E-07	0.000370067 1.3695E-07	0.000327115 1.07004E-07				
y _i - y	-0.000704528	-0.000365101	0.001034906	3.47226E-05				
(y _j - y)^2	4.96359E-07	1.33299E-07	1.07103E-06	1.20566E-09				
Coverage factor (p)	95.45	%						
у	0.750145316					E _{Lprop}	0.0016	
,	222100.10					—сиор		
	0.000000150	Degree of freedom (v _e)	u _e ⁴ /v _e				0.5000	
U _{rep}	0.000333156	16	3.07985E-17			L _{measstd}	0.5008 Degree of freedom	
Ugeo	0.000376596	3	4.19046E-16			U _{measstd}	0.000482183 8	
E∟	0.0012							
Ucorr	0.000252488	9	4.51562E-16					
U _{temp}	9.95739E-07	∞	0					

9.95739E-07

Calibrated value

standard uncertainty

Extended uncertainty

CALCULATION OF LENGTH CALIBRATION

		Object of calibration							
gth of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{aW}) [K ⁻¹]	$(u_{TW}^2 + u_{TWS}^2) [K^2]$	$u_{\alpha M}$	(T _v – 20°C	$T(T_W - 20^{\circ}C)$			
0.75	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5	., ()			
-		Reference artefact used							
Туре	Part number	Nominal length /mm	Calibrated length /mm	U calibration /mm	k				
ige block	-	0.75	0.500000	0.000	1 2				
	0.51.5								
Measurement repetition name	Position 1	asurments: 4 positions, 5 repeatitions each Position 2	Position 3	Position 4	-	Measurements No.	Gauge block measurement Position 1 P	osition 2	Position 3
30	0.749800	0.749600	0.751000	0.750700		1	0.5009	0.5009	0.500
30	0.749900	0.749600	0.750500	0.750000		2	0.5013	0.5013	0.50
30 30	0.749900 0.750100	0.749200 0.749400	0.751200 0.751100	0.750000 0.750100		3	0.5002	0.5002	0.500
30	0.749900	0.749600	0.750800	0.749800					
y _i S _i	0.749920048	0.749480036	0.750920138	0.75012016					
S _j (S _j)^2	0.000109559 1.20033E-08	0.000178912 3.20095E-08	0.000277587 7.70543E-08	0.000342085 1.17022E-07					
y _i - y	-0.000190048	-0.00063006	0.000810043	1.00643E-05					
(y _j - y)^2	3.61181E-08	3.96975E-07	6.56169E-07	1.01291E-10					
Coverage factor (p)	95.45	%							
						_	0.0040		
у	0.750110096					E _{Lprop}	0.0016		
		Degree of freedom (ve)	u_e^4/v_e						
U _{rep}	0.000243972	16	8.85727E-18			L _{measstd}	0.5008		
u_{geo}	0.000301298	3	1.71689E-16			U _{measstd}	0.000482183	e of freedom 8	
		· ·	11.10002 10			• meassio	0.000102100	Ü	
EL	0.0012								
U _{corr}	0.000252488	9	4.51562E-16						
	9.95739E-07		0						
U _{temp}	9.95739E-07	~	U						
]		_				
Calibrated value	0.748910096		Effective degree of freedom	15					
standard uncertainty	0.000313609								
	0.404405000								
k factor	2.181165682								
Extended uncertainty	0.000684033								
		CALCIII ATION	LOBIENCTI	TCATIDI	DATIC	N.T			
		CALCULATION	OF LENGII	1 CALIBI	KAIIC	JIN			
		Object of calibration							
ength of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{aw}) [K ⁻¹]	$(u_{TW}^2 + u_{TWS}^2) [K^2]$	u_{aM}	(T _M – 20°C	$T(T_W - 20^{\circ}C)$			
0.75	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5				
		Reference artefact used							
Type auge block	Part number	Nominal length /mm 0.7	Calibrated length /mm 0.500000	U _{calibration /mm} 0.000	k)1 2				
auge block		0.71	0.00000	0.000	2				
	Calibration me	easurments: 4 positions, 5 repeatitions each	·h		¬ '		Gauge block measurement		
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	-	Measurements No.	Position 1 Po	osition 2	Position 3
9-35	0.750800	0.749700	0.749901	0.750700	7 [1	0.5009	0.5009	0.500
9-35	0.750200 0.750500	0.749500 0.749601	0.749600 0.749601	0.750900 0.750401		2	0.5013	0.5013	0.501
9-35 9-35	0.750900	0.749801	0.749801	0.750100	'	<u> </u>	0.5002	0.5002	0.500
9-35	0.750500	0.749600	0.749700	0.750600					
y _j S _j	0.750580069 0.000277469	0.749680684	0.74972058	0.75054034					
(S _j)^2	7.69891E-08	0.000193149 3.73066E-08	0.000130422 1.70098E-08	0.00030484 9.29273E-08					
y _i - y	0.000449651	-0.000449734	-0.000409838	0.000409921					
(y _j - y)^2	2.02186E-07	2.02261E-07	1.67967E-07	1.68036E-07	_				
Coverage factor (p)	95.45]%							
у	0.750130418	1				E _{Lprop}	0.0016		
,	223100110					-chob			
	0.00000700	Degree of freedom (v _e)	u _e ⁴ /v _e				0.5000		
U _{rep}	0.000236766	16	7.85631E-18			L _{measstd}	0.5008 Degree	e of freedom	
U _{geo}	0.000248403] 3	7.93209E-17			U _{measstd}	0.000482183	8	
EL	0.0012	1							
	•								
Ucorr	0.000252488	9	4.51562E-16						

0

Appendix (6)

								Stitchi	ng 5x								
		Horizon	tal1					Vertic	al1					Diagor	nal1		
	1	2	3	4	5		1	2	3	4	5		1	2	3	4	
L	0.004001	0.004001	0.004001	0.004001	0.004001	L	0.004001	0.004001	0.004	0.004002	0.004	L	0.005657	0.005657	0.005658	0.005657	
σ1	0.259403	0.241083	0.744631	0.407013	0.607471	σ1	0.239937	0.42981	0.506968	0.455065	0.166409	σ1	0.410882	0.655984	0.439901	0.987645	5
σ2	0.000171	0.000233	0.000231	0.00029	0.000195	σ2	0.00023	0.000215	0.000278	0.000379	0.000324	σ2	0.000253	0.0003	0.000287	0.000279	
σ3	0.046811	0.046812	0.046812	0.046812	0.046807	σ3	0.046814	0.046808	0.046802	0.046821	0.046806	σ3	0.066187	0.066187	0.066199	0.066187	
σ4	0.004681	0.004681	0.004681	0.004681	0.004681	σ4	0.004681	0.004681	0.00468	0.004682	0.004681	σ4	0.006619	0.006619	0.00662	0.006619	1
σtotal	0.263634	0.24563	0.746116	0.409723	0.60929	O total	0.244506	0.432377	0.509145	0.457491	0.17293	O total	0.416232	0.659348	0.444903	0.989883	_

$$\begin{split} &\sigma 1 = \text{standard deviation /sqrt(3)} \\ &\sigma 2 = \text{standard uncertainty calibration of each length} \\ &\sigma 3 = (L^*11.7^*1) \text{ L=m / Gateei} = 11.7 / \Delta T = (21-20 \text{ C'}) \\ &\sigma 4 = (L^*10.8^*11.7^*1) \\ &\Gamma 4 = (L^*10.8^*11.7^*1)$$

		or calcul	ation		
	L1	L2	L3	L4	L5
Difference1	-3.15437	-3.51956	-1.57083	-1.80401	-5.98387
Difference2	-2.89464	-4.54167	-4.59927	-3.04527	-5.66216
Difference3	-3.95069	-4.06373	-3.86407	-3.46429	-8.03755
Mean	-3.33324	-4.04165	-3.34472	-2.77119	-6.56119
SD	0.449299	0.417568	1.289739	0.704967	1.052171
SD/sqrt(3)	0.259403	0.241083	0.744631	0.407013	0.607471
	0.259403	0.241083	0.744631	0.407013	0.607471

	Horizor	ital1		
				_
1	2	3	4	5
0.004001	0.004001	0.004001	0.004001	0.004001
0.83557	0.344805	0.193671	0.098142	0.462276

	1	2	3	4	5
L	0.004001	0.004001	0.004001	0.004001	0.004001
σ1	0.83557	0.344805	0.193671	0.098142	0.462276
σ2	0.000171	0.000233	0.000231	0.00029	0.000195
σ3	0.046811	0.046812	0.046812	0.046812	0.046807
σ4	0.004681	0.004681	0.004681	0.004681	0.004681
O total	0.836893	0.348	0.199304	0.108836	0.464663

$$\begin{split} \sigma l = & standard \ deviation \ / sqrt(3) \\ \sigma 2 = & standard \ uncertainty \ calibration \ of each \ length \\ \sigma 3 = & (t^+11.7^+1) \ l = m \ / \sigma a teel = 11.7 \ / \Delta T = (21-20 \ C') \\ \sigma 4 = & (t^+10.8^+11.7^+1) \\ L = & uncertainty \ calculation \ of \ length \end{split}$$

σ1 calculation										
	L1	L2	L3	L4	L5					
Difference1	0.707757	3.525121	6.968984	8.922901	12.39222					
Difference2	-2.60765	2.632385	6.209487	9.293297	10.89709					
Difference3	0.136999	4.082393	6.860786	8.943369	10.5454					
Mean	-0.58763	3.4133	6.679753	9.053189	11.27824					
SD	1.44725	0.597221	0.335449	0.169987	0.800685					
SD/sqrt(3)	0.83557	0.344805	0.193671	0.098142	0.462276					

σ1 calculation	

	L1	L2	L3	L4	L5
Difference1	-0.95031	-1.42211	-5.44237	-6.36042	-4.93567
Difference2	-1.80169	-2.15855	-4.06126	-6.36042	-4.93567
Difference3	-0.89272	-0.34562	-3.32384	-4.68841	-4.32424
Mean	-1.21491	-1.30876	-4.27583	-5.80308	-4.73186
SD	0.415583	0.744453	0.878094	0.788195	0.288229
SD/sqrt(3)	0.239937	0.42981	0.506968	0.455065	0.166409

NOStitching 5x

Vertical1											
	1	2	3	4	5						
L	0.004001	0.004001	0.004	0.004002	0.004						
σ1	0.228039	0.174396	0.343423	0.508731	0.624497						
σ2	0.00023	0.000215	0.000278	0.000379	0.000324						
σ3	0.046814	0.046808	0.046802	0.046821	0.046806						
σ4	0.004681	0.004681	0.00468	0.004682	0.004681						
σtotal	0.232842	0.180629	0.346629	0.510902	0.626266						

σ1 calculation

L1	L2	L3	L4	L5
2.605533	1.670291	2.731725	5.098249	6.197867
1.942447	2.248775	1.449322	3.139674	3.555312
2.884123	2.35904	2.689491	3.333544	4.710372
2.477368	2.092702	2.290179	3.857156	4.821183
0.394975	0.302063	0.594826	0.881148	1.08166
0.228039	0.174396	0.343423	0.508731	0.624497
	2.605533 1.942447 2.884123 2.477368 0.394975	2.605533 1.670291 1.942447 2.248775 2.884123 2.35904 2.477368 2.092702 0.394975 0.302063	2.605533 1.670291 2.731725 1.942447 2.248775 1.449322 2.884123 2.35904 2.689491 2.477368 2.092702 2.290179 0.394975 0.302063 0.594826	2.605533 1.670291 2.731725 5.098249 1.942447 2.248775 1.449322 3.139674 2.884123 2.35904 2.689491 3.333544 2.477368 2.092702 2.290179 3.857156 0.394975 0.302063 0.594826 0.881148

σ1 calculation

L1	L2	L3	L4	L5
-6.162	-9.30429	-9.62691	-4.59953	-12.5902
-4.42106	-6.65048	-7.97987	-8.34161	-11.7672
-5.21424	-7.25127	-8.04321	-8.10339	-9.49748
-5.26577	-7.73535	-8.55	-7.01484	-11.285
0.711669	1.136198	0.76193	1.710652	1.307828
0.410882	0.655984	0.439901	0.987645	0.755075
	-6.162 -4.42106 -5.21424 -5.26577 0.711669	-6.162 -9.30429 -4.42106 -6.65048 -5.21424 -7.25127 -5.26577 -7.73535 0.711669 1.136198	-6.162 -9.30429 -9.62691 -4.42106 -6.65048 -7.97987 -5.21424 -7.25127 -8.04321 -5.26577 -7.73535 -8.55 0.711669 1.136198 0.76193	-6.162 -9.30429 -9.62691 -4.59953 -4.42106 -6.65048 -7.97987 -8.34161 -5.21424 -7.25127 -8.04321 -8.10339 -5.26577 -7.73535 -8.55 -7.01484 0.711669 1.136198 0.76193 1.710652

	Diagonal1											
1 2 3 4 5												
L	0.005657	0.005657	0.005658	0.005657	0.005658							
σ1	0.540908	0.814386	0.438778	0.194281	0.935505							
σ2	0.000253	0.0003	0.000287	0.000279	0.000393							
σ3	0.066187	0.066187	0.066199	0.066187	0.066199							
σ4	0.006619	0.006619	0.00662	0.006619	0.00662							
O total	0.544983	0.817098	0.443793	0.205353	0.937868							

σ1 calculation

		L1	L2	L3	L4	L5	
	Difference1	-0.74527	2.654456	3.965443	5.743857	9.401351	
	Difference2	-1.24455	0.030823	2.220218	6.350174	6.687872	
	Difference3	0.94491	3.289676	3.653851	6.530591	10.55311	
	Mean	-0.3483	1.991652	3.279837	6.208207	8.880778	
1	SD	0.936881	1.410559	0.759986	0.336505	1.620343	
	SD/sqrt(3)	0.540908	0.814386	0.438778	0.194281	0.935505	
	SD/sqrt(3)	0.540908	0.814386	0.438778	0.194281	0.935505	

Appendices

	Stitching 10x																	
		Horizor	ital1						Vertic	al1					Diagor	nal1		
	1	2	3	4	5			1	2	3	4	5		1	2	3	4	5
L	0.004001	0.004001	0.004001	0.004001	0.004001		L	0.004001	0.004001	0.004	0.004002	0.004	L	0.005657	0.005657	0.005658	0.005657	0.0056
σ1	0.50355	0.47857	0.516405	0.345264	0.5838		σ1	0.206186	0.294832	0.331344	0.547049	0.411302	σ1	0.168829	0.431065	0.115921	0.218326	0.302
σ2	0.000171	0.000233	0.000231	0.00029	0.000195		σ2	0.00023	0.000215	0.000278	0.000379	0.000324	σ2	0.000253	0.0003	0.000287	0.000279	0.0003
σ3	0.046811	0.046812	0.046812	0.046812	0.046807		σ3	0.046814	0.046808	0.046802	0.046821	0.046806	σ3	0.066187	0.066187	0.066199	0.066187	0.0661
σ4	0.004681	0.004681	0.004681	0.004681	0.004681		σ4	0.004681	0.004681	0.00468	0.004682	0.004681	σ4	0.006619	0.006619	0.00662	0.006619	0.006
σtotal	0.505743	0.480877	0.518544	0.348455	0.585692		σtotal	0.211486	0.298561	0.334665	0.549069	0.413983	σtotal	0.18146	0.436167	0.133656	0.228234	0.310

 $\sigma 1$ = standard deviation /sqrt(3) $\sigma 2$ = standard uncertainty calibration of each length $\sigma 3$ = ($\pm 11.7^{-1}$) ($\pm m$) ($\Delta 1$) (

σ1 calculation										
	L1	L2	L3	L4	L5					
Difference1	-2.94076	-2.83245	-1.78305	-2.27474	-4.88644					
Difference2	-1.55076	-3.08245	-2.82305	-2.71474	-3.18644					
Difference3	-0.84076	-1.21245	-0.63305	-1.28474	-2.47644					
Mean	-1.77743	-2.37579	-1.74639	-2.09141	-3.51644					
SD	0.872175	0.828908	0.89444	0.598015	1.011171					
SD/sqrt(3)	SD/sqrt(3) 0.50355		0.516405	0.345264	0.5838					
	0.50355	0.47857	0.516405	0.345264	0.5838					

of calculation										
	L1	L2	L3	L4	L5					
Difference1	-0.08987	-0.83051	-1.95735	-0.4797	-2.60245					
Difference2	-0.7807	-0.09655	-2.9573	-2.21317	-3.7341					
Difference3	-0.90002	-1.34073	-3.31302	-2.68298	-4.31862					
Mean	-0.5902	-0.75593	-2.74256	-1.79195	-3.55173					
SD	0.357125	0.510663	0.573904	0.947517	0.712396					
SD/sqrt(3) 0.20618		0.294832	0.331344	0.547049	0.411302					

σ1 calculation

		OI calcu	ation		
	L1	L2	L3	L4	L5
Difference1	-5.29944	-4.27425	-6.5325	-6.583	-7.7869
Difference2	-4.79359	-5.74334	-7.0154	-7.43992	-8.5743
Difference3	-4.60733	-4.06547	-6.85468	-6.70687	-9.0602
Mean	-4.90012	-4.69435	-6.80086	-6.90993	-8.47389
SD	0.29242	0.746626	0.200781	0.378152	0.52465
SD/sqrt(3)	0.168829	0.431065	0.115921	0.218326	0.30291

	Horizontal1											
	1 2 3 4 5											
L	0.004001	0.004001	0.004001	0.004001	0.004001							
σ1	0.427404	0.244146	0.030307	0.253903	0.194727							
σ2	0.000171	0.000233	0.000231	0.00029	0.000195							
σ3	0.046811	0.046812	0.046812	0.046812	0.046807							
σ4	0.004681	0.004681	0.004681	0.004681	0.004681							
O total	0.429985	0.248638	0.055963	0.258225	0.200328							

 $\begin{array}{l} \sigma 1 = \text{standard deviation /sqrt(3)} \\ \sigma 2 = \text{standard uncertainty calibration of each length} \\ \sigma 3 = (L^*11.7^*1) \ L=m / \sigma_{\text{steel}} = 11.7 / \Delta T = (21-20 \ C') \\ \sigma 4 = (L^*10.8^*11.7^*1) \\ L = \text{uncertainty calculation of length} \end{array}$

NOStitching 10x									
Vertical1									
1 2 3 4 5									
L	0.004001	0.004001	0.004	0.004002	0.004				
σ1	0.19112	0.525027	0.452473	0.244452	0.59943				
σ2	0.00023	0.000215	0.000278	0.000379	0.00032				
σ3	0.046814	0.046808	0.046802	0.046821	0.046806				
σ4	0.004681	0.004681	0.00468	0.004682	0.004681				
σtotal	0.196826	0.52713	0.454911	0.248939	0.601277				

	Diagonal1									
	1	2	3	4	5					
L	0.005657	0.005657	0.005658	0.005657	0.00565					
σ1	0.244163	0.647634	0.365096	0.847454	1.17560					
σ2	0.000253	0.0003	0.000287	0.000279	0.00039					
σ3	0.066187	0.066187	0.066199	0.066187	0.066199					
σ4	0.006619	0.006619	0.00662	0.006619	0.00662					
σtotal	0.253062	0.651041	0.371108	0.85006	1.177486					

σ1 calculation

	L1	L2	L3	L4	L5
Difference1	1.229237	2.897545	6.296948	8.405256	11.02356
Difference2	-0.57076	2.477545	6.196948	9.215256	11.75356
Difference3	0.519237	3.507545	6.316948	9.425256	11.05356
Mean	0.39257	2.960878	6.270281	9.015256	11.2769
SD	0.740285	0.422874	0.052493	0.439773	0.337277
SD/sqrt(3)	0.427404	0.244146	0.030307	0.253903	0.194727

	σ1 calculation											
		L1	L2	L3	L4	L5						
	Difference1	2.321336	2.896817	3.270479	3.627024	5.730658						
	Difference2	1.598583	0.893792	1.35126	2.911863	3.195342						
	Difference3	2.278292	2.739248	2.274377	3.919922	4.289875						
	Mean	2.06607	2.176619	2.298705	3.48627	4.405292						
1	SD	0.33103	0.909374	0.783707	0.423403	1.038251						
	SD/sqrt(3)	0.19112	0.525027	0.452473	0.244452	0.599434						

	01 Calculation									
		L1	L2	L3	L4	L5				
	Difference1	-0.86155	2.257287	3.578085	7.487302	9.73071				
	Difference2	-1.54638	1.142401	2.467661	6.084607	6.62662				
	Difference3	-0.53086	3.874718	3.958129	9.652962	11.5596				
	Mean	-0.97959	2.424802	3.334625	7.741624	9.305668				
1	SD	0.422903	1.121735	0.632365	1.467833	2.036208				
	SD/sqrt(3)	0.244163	0.647634	0.365096	0.847454	1.175605				

Appendix (7)

	5x												
Horizontal				Vertical				Diagonal					
	1	2	3			1	2	3			1	2	3
L	0.000753	0.001502	0.002253		L	0.000746	0.001497	0.002247		L	0.001062	0.002124	0.003189
σ1	0.94767	0.993733	0.452262		σ1	0.413889	1.306672	3.524275		σ1	0.952082	1.385093	1.130169
σ2	0.000346	0.00035	0.000293		σ2	0.000327	0.000289	0.000329		σ2	0.000329	0.000383	0.000411
σ3	0.008812	0.017577	0.026364		σ3	0.008733	0.017517	0.02629		σ3	0.012425	0.024851	0.037311
σ4	0.000881	0.001758	0.002636		σ4	0.000873	0.001752	0.002629		σ4	0.001243	0.002485	0.003731
σtotal	0.947711	0.99389	0.453037		σtotal	0.413982	1.306791	3.524374		σtotal	0.952164	1.385318	1.130791

 $\begin{array}{l} \sigma 1= \text{ standard deviation / sqrt(3)} \\ \sigma 2= \text{ standard uncertainty calibration of each length} \\ \sigma 3= (L^*11.7^*1) \ L=m \ / \sigma_{\text{steel}} = 11.7 \ / \Delta T = (21-20 \ C') \\ \sigma 4= (L^*10\%^*11.7^*1) \end{array}$

L= uncertainty calculation of length

σ1 calculation									
	L1	L2	L3						
Difference1	-3.35993	-5.78753	-7.15771						
Difference2	-5.46054	-3.51615	-6.34042						
Difference3	-7.37918	-7.72787	-8.2525						
Mean	-5.39988	-5.67718	-7.25021						
SD	1.641412	1.721195	0.78334						
SD/sqrt(3)	0.94767	0.993733	0.452262						

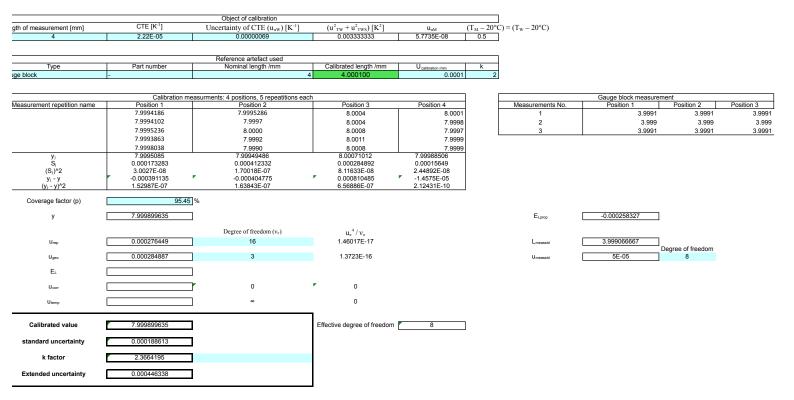
	σ1 calculation								
	L1	L2	L3						
Difference1	3.098154	2.685972	7.195268						
Difference2	1.887945	0.475506	-7.612						
Difference3	1.391165	-2.82212	-2.00715						
Mean	2.125755	0.113119	-0.80796						
SD	0.716876	2.263222	6.104224						
SD/sqrt(3)	0.413889	1.306672	3.524275						

σ1 calculation									
	L1	L2	L3						
Difference1	-2.15457	-2.95827	-9.35158						
Difference2	-2.72303	-6.92309	-14.083						
Difference3	-5.90216	-8.69696	-11.0437						
Mean	-3.59325	-6.19277	-11.4927						
SD	1.649055	2.399051	1.95751						
SD/cart/3)	0.952082	1 385003	1 130160						

Appendix (8) - X value

CALCULATION OF LENGTH CALIBRATION

		Object of calibration				1			
.ength of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{ow}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS})[K^2]$	u_{aM}	(T – 20°	$C) = (T_w - 20^{\circ}C)$			
4	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5	1			
•	Z.ZZZ 00	0.0000000	0.00000000	0.77002.00	0.0	1			
		Reference artefact used				1			
Туре	Part number	Nominal length /mm	Calibrated length /mm	U calibration /mm	l k	1			
Sauge block	-	A Communication of the Communi	4.000100	0.0001					
	•				•	•			
	Calibration mo	asurments: 4 positions, 5 repeatitions eac	h		1		Gauge block measurem	nont	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	1	Measurements No.	Position 1	Position 2	Position 3
-2	3.9998395	3.9995	4.0006	4.0003	1	1	3.9991	3.9991	3.9991
-2	3.9995633	4.0001	4.0006	4.0001		2	3.999	3.999	3.999
-2	3.9996315	3.9996	4.0010	3.9996		3	3.9991	3.9991	3.9991
-2	3.999381	3.9997	4.0004	3.9999					
-2	3.9999899	4.0000	4.0010	3.9997	1				
y _i	3.99968104	3.99978194	4.0007463 0.000279497	3.99993284					
S _i (S _i)^2	0.000238141 5.67112E-08	0.000247735 6.13727E-08	7.81186E-08	0.000264209 6.98064E-08					
y ₁ - y		-0.00025359		-0.00010269					
(y _j - y)^2	1.25663E-07	6.43079E-08	5.05194E-07	1.05452E-08					
Coverage factor (p)	95.45	%							
у	4.00003553					E _{Lprop}	-0.000258327		
,									
		Degree of freedom (ve)	u_e^4/v_e						
U _{rep}	0.00025788	16	1.10564E-17			L _{measstd}	3.999066667		
	0.000242506	3	7.20525E-17				5E-05	Degree of freedom 8	
Ugeo	0.000242506	3	7.20525E-17			Umeasstd	3E-03	0	
E∟									
		_	7 0						
U _{corr}		0	0						
U _{temp}		∞	0						
- ump		l.	<u></u>						
		1	1		,				
Calibrated value	4.000035530		Effective degree of freedom	9	_				
standard uncertainty	0.00016734								
k factor	2.319809441								
Extended uncertainty	0.000388197								
	0.000000191	<u> </u>							
		_	_						

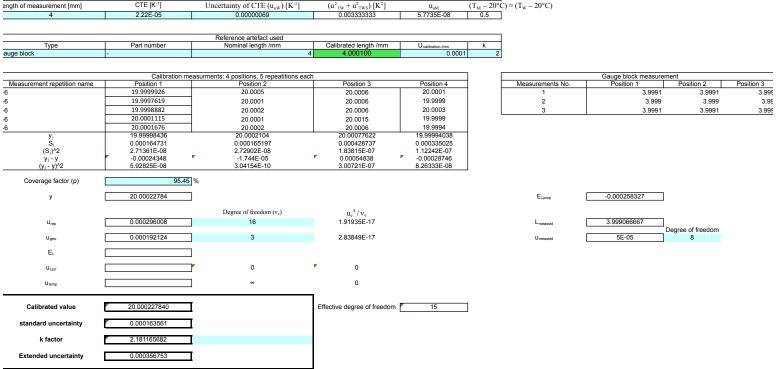


0.000609294

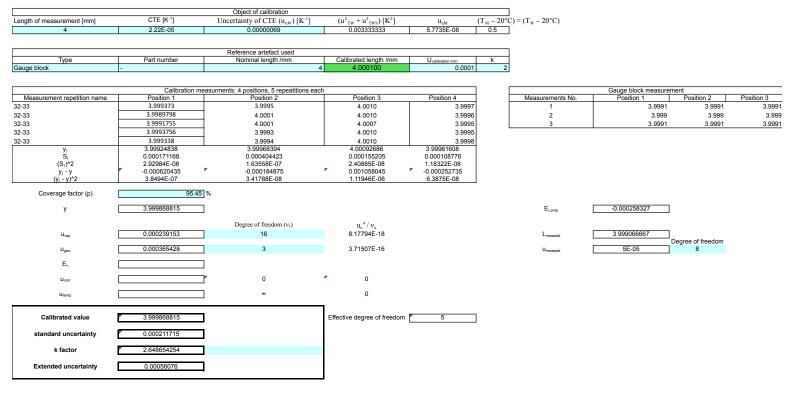
Extended uncertainty

		Object of calibration							
gth of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{ow}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS})[K^2]$	$u_{\alpha M}$	$(T_{\rm M} - 20^{\circ})$	$(C) = (T_W - 20^{\circ}C)$			
4	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5				
	•		•	•	•	'			
		Reference artefact used							
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	l k				
ige block	- art number	Normina lengur/mm	4 4.000100	0.0001	2				
ago block			1.000100	0.0001					
					_				
		asurments: 4 positions, 5 repeatitions ea					Gauge block measurer		
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	-	Measurements No.	Position 1	Position 2	Position 3
	11.9991632	11.9998016	12.0014	12.0003		1	3.9991	3.9991	3.9991
	11.9986938	11.9998	12.0014	12.0002		2	3.999	3.999	3.999
	11.9990304	12.0001	12.0008	11.9998		3	3.9991	3.9991	3.9991
	11.9995247	12.0000	12.0007	11.9999					
	11.9994871	12.0002	12.0009	12.0001					
y _i S _i	11.99917984 0.000343577	11.99997624 0.000189063	12.00106228 0.000349414	12.00007384 0.000195976					
(S _j)^2	1.18045E-07	3.5745E-08	1.2209E-07	3.84065E-08					
(3 ₁) 2 y ₁ - y	-0.00089321			7.9E-07					
(y, - y)^2	7.97824E-07	9.37218E-09	9.78576E-07	6.241E-13					
					-				
Coverage factor (p)	95.45	%							
.,	12.00007305					E _{Lprop}	-0.000258327		
у	12.00007305					□Lprop	-0.000258327		
		Degree of freedom (v _e)	u_{r}^{4}/v_{r}						
U _{rep}	0.000280307	16	1.54338E-17			L _{measstd}	3.999066667		
Urep	0.000280307	10	1.34336E-17			∟measstd		Degree of freedom	
Ugeo	0.000385765	3	4.61369E-16			U _{measstd}	5E-05	8	
E∟									
		0	7 0						
Ucorr		U	. 0						
U _{temp}		∞	0						
- turnp			-						
			1						
Calibrated value	12.000073050		Effective degree of freedom	5]				
standard uncertainty	0.000230039								
k factor	2.648654254								
K tactor	2.648654254								

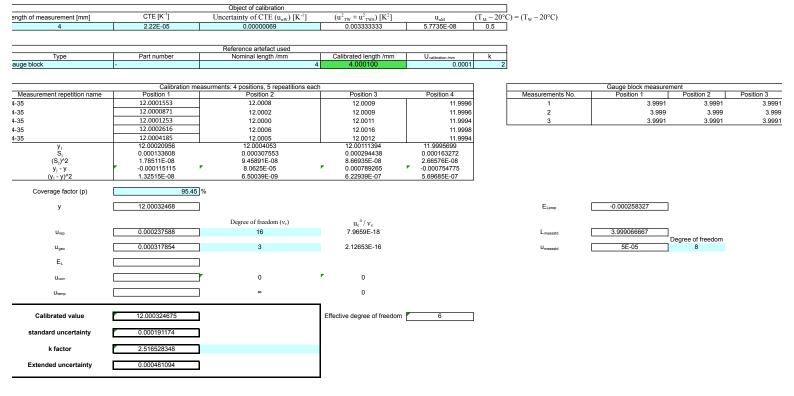
		Object of calibration				1			
gth of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{aW}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS})[K^2]$	$u_{\alpha M}$	(T _v - 20°	$C) = (T_W - 20^{\circ}C)$			
4	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5	1			
	'		•			-			
		Reference artefact used				7			
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
ige block	-	4	4.000100	0.0001	2				
M		asurments: 4 positions, 5 repeatitions each		D# 4	1	Managements No.	Gauge block measur		Di4: 2
Measurement repetition name	Position 1 15.9994451	Position 2 15.9991	Position 3 16.0015	Position 4 16.0003	+	Measurements No.	Position 1 3.999	Position 2 1 3.9991	Position 3 3.9991
	15.9996318	15.9992	16.0015	16.0003		2	3.999		3.999
	15.9993634	16.0004	16.0015	16.0004		3	3.999		3.9991
	15.9993881	15.9991	16.0012	16.0004			0.000	0.0001	0.0001
	15.9994282	15.9990	16.0014	16.0004					
y _i	15.99945132	15.9993637	16.00140426	16.0003848	1				
y _i S _j	0.000105916	0.000594877	0.000100407	6.88192E-05					
(S _j)^2	1.12182E-08	3.53879E-07	1.00815E-08	4.73609E-09					
y _i - y (y _i - y)^2	-0.0006997 4.8958E-07	-0.00078732 6.19873E-07	0.00125324 1.57061E-06	0.00023378 5.46531E-08					
	*		1.07001E-00	5.40001E-00	J				
Coverage factor (p)	95.45	%							
у	16.00015102					E _{Lprop}	-0.000258327]	
		Degree of freedom (v _c)	u_e^4/v_e						
U _{rep}	0.000308186	16	2.25524E-17			L _{measstd}	3.999066667		
u_{geo}	0.000477381	3	1.08198E-15			U _{measstd}	5E-05	Degree of freedom 8	
E∟									
U _{corr}		0	0						
U _{temp}		00	0						
			7						
Calibrated value	16.000151020		Effective degree of freedom	5]				
standard uncertainty	0.000275625								
k factor	2.648654254								
Extended uncertainty	0.000730035								
			_						
		CALCULATIO	N OF LENCT	TH CALIR	RAT	ION			
		CALCULATIO	IV OF LENUI		IXXI.	1011			
		Object of calibration				_			
anoth of massurament [mm]	CTE IK-1	Uncertainty of CTE (u) [V-1]	$(n^2 \pm n^2) \Gamma V^2$		(T :	20°C) = (T 20°C)			



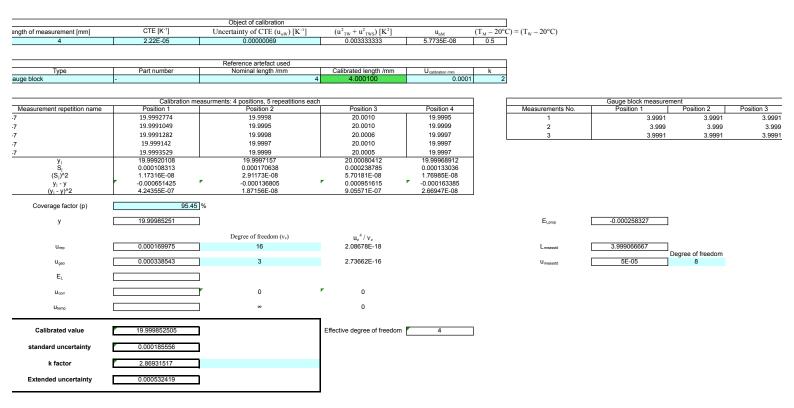
		Object of calibration				1			
ength of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{gW}) [K ⁻¹]	$(u_{TW}^2 + u_{TWS}^2) [K^2]$	$u_{\alpha M}$	(T _v – 20°	$^{1}C) = (T_{W} - 20^{\circ}C)$			
4	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5	1			
						_			
		Defended added				7			
Type	Part number	Reference artefact used Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	l k	-			
auge block	-	Normal length 7mm	4 4.000100	0.000					
						_			
	Calibration ma	asurments: 4 positions, 5 repeatitions each	ala.		_		Gauge block measurer	mont	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	-	Measurements No.	Position 1	Position 2	Position 3
1-32	23.9986056	23.9998	24.0007	23.9996	6	1	3.9991	3.9991	3.999
1-32	23.9988974	23.9998	24.0007	23.9996		2	3.999	3.999	3.99
1-32	23.9984906	23.9996	24.0009	23.999		3	3.9991	3.9991	3.999
1-32	23.9995371	23.9996	24.0015	24.0003			_		
1-32	23.9996635	23.9993	24.0008	23.9996	6				
y _i	23.99903884	23.9996008	24.00092184	23.99972286					
S _j	0.000535428 2.86683E-07	0.000211381 4.46819E-08	0.000338788	0.00030323 9.19486E-08					
(S _j)^2 y _i - y		-0.000220285	1.14777E-07 0.001100755	9.19486E-08 -9.8225E-05					
(y _i - y)^2	6.11907E-07	4.85255E-08	1.21166E-06	9.64815E-09					
	-				_				
Coverage factor (p)	95.45	%							
	23.99982109					E _{Lprop}	-0.000258327		
у	23.99962109					⊏Lprop	-0.000230327		
		Degree of freedom (v _c)	u_e^4/v_e						
U _{rep}	0.000366773	16	4.52409E-17			$L_{measstd}$	3.999066667		
								Degree of freedom	
U _{geo}	0.000395995	3	5.12291E-16			U _{measstd}	5E-05	8	
E∟									
EL									
Ucorr		0	0						
		00	0						
U _{temp}		∞	0						
			7						
Calibrated value	23.999821085		Effective degree of freedom	7	7				
			1		_				
standard uncertainty	0.000257114								
la finata n	0.40000000								
k factor	2.428809082								
Extended uncertainty	0.00062448		1						
	0.00002110								
			-						



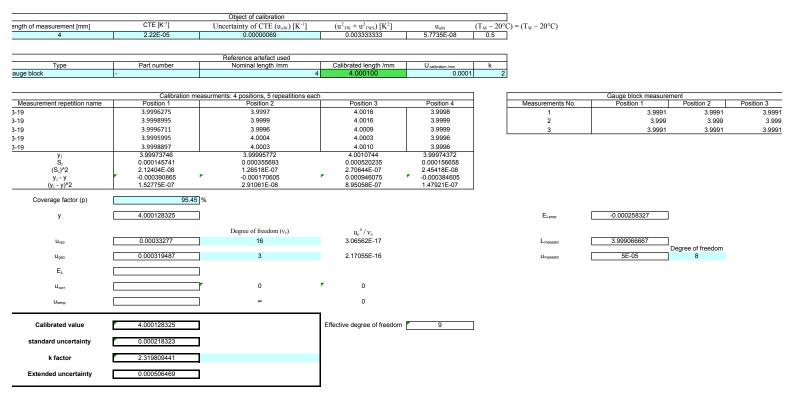
		Object of calibration				1			
n of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{aw}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS})[K^2]$	$u_{\alpha M}$	(T., - 20°	$(C) = (T_W - 20^{\circ}C)$			
4	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5]			
	•		•	•		•			
T	Dark average a	Reference artefact used	Calibrated Investor (see						
Type e block	Part number	Nominal length /mm	Calibrated length /mm 4 4.000100	U _{calibration /mm} 0.0001	k 2	1			
BIOCK	-		4.000100	0.0001		1			
	Calibration mea	surments: 4 positions, 5 repeatitions ea	ch				Gauge block measure	ment	
easurement repetition name	Position 1	Position 2	Position 3	Position 4		Measurements No.	Position 1	Position 2	Position 3
	7.9993676	8.0001	8.0007	7.9998		1	3.9991	3.9991	3.999
	7.998938	8.0000	8.0007	7.9997		2	3.999	3.999	3.99
	7.9996097	8.0001	8.0015	7.9998		3	3.9991	3.9991	3.999
	7.999576	7.9999	8.0010	7.9998					
	7.9993268	7.9997	8.0010	8.0001					
y _i S _j	7.99936362 0.000268414	7.99997848 0.00016176	8.0009433 0.000340727	7.99984964 0.000158669					
(S _j)^2	7.20461E-08	2.61663E-08	1.16095E-07	2.51758E-08					
y _i - y	-0.00067014	-5.528E-05	0.00090954	-0.00018412					
(y _i - y)^2	4.49088E-07	3.05588E-09	8.27263E-07	3.39002E-08					
Coverage factor (p)	95.45	%							
у	8.00003376					E _{Lprop}	-0.000258327		
		Degree of freedom (ve)	u_e^4/v_e						
U _{rep}	0.000244685	16	8.9613E-18			L _{measstd}	3.999066667		
U _{geo}	0.000330821	3	2.49533E-16			U _{measstd}		Degree of freedom 8	
E∟									
Ucorr		0	• 0						
U _{temp}		∞	0						
Calibrated value	8.000033760		Effective degree of freedom	5					
standard uncertainty	0.00019833								
·									
k factor	2.648654254								
Extended uncertainty	0.000525307								
			_						
		CALCULATIO	ON OF LENGT	TH CALIB	RAT]	ION			
									_



		Object of calibration							
ngth of measurement [mm]	CTE [K-1]	Uncertainty of CTE (uaW) [K-1]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	$u_{\alpha M}$	$(T_M - 20^{\circ}C$	$T(T_{w} - 20^{\circ}C)$			
4	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5				
		Reference artefact used							
Type	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
auge block	-	4	4.000100	0.0001	2				
	Calibration me	easurments: 4 positions, 5 repeatitions each	1		1 г		Gauge block measuren	nent	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	t t	Measurements No.	Position 1	Position 2	Position 3
-36	15.9995483	16.0000	16.0013	16.0003	1 [1	3.9991	3.9991	3.999
-36	15.999489	16.0001	16.0013	16.0000		2	3.999	3.999	3.99
-36	15.9996474	16.0000	16.0014	16.0002		3	3.9991	3.9991	3.999
-36	15.9992625	16.0000	16.0010	16.0000	-		•		
-36	15.9998919	16.0004	16.0014	15.9997					
y _j S _j	15.99956782	16.00009194	16.00128044	16.00005336	İ				
S _j	0.000229769	0.000161194	0.000140596	0.000209625					
(S _j)^2	5.27937E-08	2.59837E-08	1.97673E-08	4.39425E-08 -0.00019503					
y _j - y (y _i - y)^2	-0.00068057 4.63176E-07	-0.00015645 2.44766E-08	0.00103205 1.06513E-06	-0.00019503 3.80367E-08					
(y ₁ - y) 2	•		1.000 TOE-00	3.00307 E-00	1				
Coverage factor (p)	95.45]%							
у	16.00024839]				E _{Lprop}	-0.000258327		
		Degree of freedom (v _c)	u_c^4/v_c						
U _{rep}	0.000188737	16	3.17228E-18			L _{measstd}	3.999066667		
U _{geo}	0.000364099	3	3.66131E-16			U _{measstd}	5E-05	Degree of freedom 8	
E∟		1							
Ucorr		- 0	0						
		-	_						
U _{temp}		∞	0						
Calibrated value	16.000248390	1	Effective degree of freedom	4	1				
Julio Value	10.000240000	1	Encoure degree of freedom		1				
standard uncertainty	0.000200665]							
k factor	2.86931517								
Extended uncertainty	0.000575771	1							
		4							
			=						



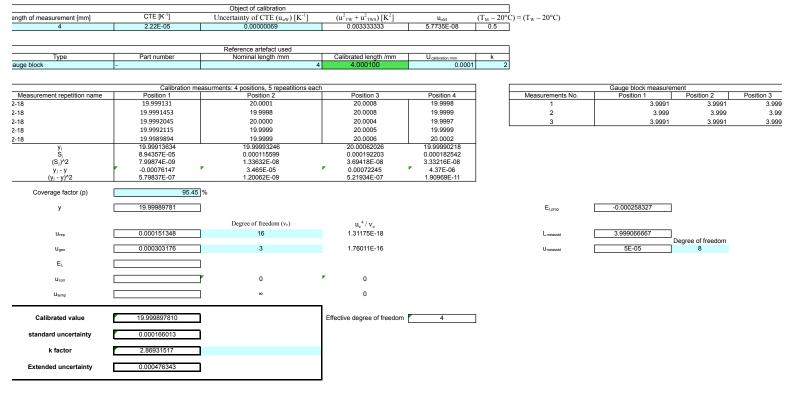
		Object of calibration				İ			
gth of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{gW}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	u_{aM}	$(T_M - 20^{\circ})$	$(T_W - 20^{\circ}C)$			
4	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5	l			
		Reference artefact used				İ			
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	l k				
ige block	-		4.000100	0.000	11 2				
-	•			•	•				
	Calibration m	easurments: 4 positions, 5 repeatitions eac	h		_		Gauge block measurer	ment	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	-	Measurements No.	Position 1	Position 2	Position 3
3	23.9992722	23.9997	24.0009	23.9999	_	1	3.9991	3.9991	3.9991
3	23.9990763	23.9997	24.0009	23.9997		2	3.999	3.999	3.999
3	23.9993174	23.9998	24.0007	23.9995		3	3.9991	3.9991	3.9991
3	23.9997928	24.0000	24.0010	23.9998			0.5501	0.0001	0.0001
3	23.9997547	23.9997	24.0008	24.0004					
V _i	23.99944268	23.99979368	24.00087514	23.99986976	-				
y _i S _i	0.000315806	0.00012995	9.4535E-05	0.000350623					
(S _j)^2	9.97333E-08	1.68869E-08	8.93687E-09	1.22936E-07					
y _i - y	-0.000552635	-0.000201635		-0.000125555					
(y _j - y)^2	3.05405E-07	4.06567E-08	7.74092E-07	1.57641E-08					
Coverage factor (p)	95.45	%							
						_			
у	23.9999532	_				E _{Lprop}	-0.000258327		
		Degree of freedom (v _c)	u_e^4/v_e						
	0.000249246	T 16	9.64828E-18			L _{measstd}	3.999066667		
U _{rep}	0.000243240		3.04020E-10			∟ meassid		Degree of freedom	
Ugeo	0.000307668	3	1.86677E-16			U _{measstd}	5E-05	8	
EL		_							
Ucorr		7 0	r 0						
Corr		, ,	O .						
U _{temp}		∞	0						
			_						
	00.000005045	•			_				
Calibrated value	23.999995315	<u>J</u>	Effective degree of freedom	6					
standard uncertainty	0.000189973	7							
standard uncertainty	0.000103313	1							
k factor	2.516528348	1							
Extended uncertainty	0.000478072	1							
			1						
		·							



		Object of calibration							
gth of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{aW}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	$u_{\alpha M}$	(T _M - 20°C	$(T_W - 20^{\circ}C)$			
4	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5) (-w <u>-</u>)			
			•	'					
		5.6							
Туре	Part number	Reference artefact used Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	l k				
ige block	- Fait fluifibei	4		0.0001					
ige block			4.000100	0.0001					
					_				
		asurments: 4 positions, 5 repeatitions each					Gauge block measurer		
Measurement repetition name	Position 1	Position 2	Position 3	Position 4		Measurements No.	Position 1	Position 2	Position 3
25	7.9994407	8.0000	8.0015	8.0005		1	3.9991	3.9991	3.9991
25	7.9989762	7.9999	8.0015	7.9999		2	3.999	3.999	3.999
25	7.9992685	8.0000	8.0005	7.9999		3	3.9991	3.9991	3.9991
25	7.9993773	7.9998	8.0009	7.9999					
25	7.9992678	8.0000	8.0007	8.0007					
y _j S _i	7.9992661	7.9999521	8.0010182	8.00015848					
S _j	0.000178116	7.09823E-05 5.03848E-09	0.000459444 2.11089E-07	0.000392135					
(S _i)^2	3.17253E-08 -0.00083262	-0.00014662	0.00091948	1.5377E-07 5.976E-05					
y _i - y (y _i - y)^2	6.93256E-07	2.14974E-08	8.45443E-07	3.57126E-09					
(y) - y) 2	0.302302-01	2.143742-00	0.404402-07	0.07 120E-03	J				
Coverage factor (p)	95.45	%							
-									
у	8.00009872					E _{Lprop}	-0.000258327		
		D 66 1 ()	4.4						
		Degree of freedom (v _e)	u_e^4 / v_e						
U _{rep}	0.000316868	16	2.52032E-17			Lmeasstd	3.999066667	Degree of freedom	
U _{geo}	0.00036099	3	3.53786E-16			U _{measstd}	5E-05	8	
U geo	0.00000033	ű	3.337 GGE-10			Umeasstd	3E-03	U	
E∟									
Ucorr		0	0						
		eo	0						
U _{temp}		~	0						
			7						
Calibrated value	8.000098720		Effective degree of freedom	7	1				
					-				
standard uncertainty	0.000229477								
k factor	2.428809082								
	0.000557055								
Extended uncertainty	0.000557355								
			_						

$ \begin{array}{c ccccccccccccccccccccccccccccccccccc$			Object of calibration				1			
Reference artificial toald September Part number Nominual longth from Ventreal toal	ength of measurement [mm]	CTE [K-1]		$(u_{TW}^2 + u_{TWS}^2) [K^2]$	u_{aM}	$(T_{\rm M} - 20^{\circ})$	$(C) = (T_W - 20^{\circ}C)$			
Type Part number Nominal length /mm Calibrated length /mm Usebours in Measurement (Calibration measurements 4 0.000100 0.0001 2 Calibration measurements 4 0.000100	4	2.22E-05	0.0000069			0.5]			
Type Part number Nominal length /mm Calibrated length /mm Usebours in Measurement (Calibration measurements 4 0.000100 0.0001 2 Calibration measurements 4 0.000100		•		•	•	•	•			
Type Part number Nominal length /mm Calibrated length /mm Usebours in Measurement (Calibration measurements 4 0.000100 0.0001 2 Calibration measurements 4 0.000100			Potoronco artofact used				1			
Calibration measurement	Type	Part number		Calibrated length /mm	Ucalibration (mm	l k				
Design Position	auge block	-								
Design Position		•	•				•			
Design Position		Calibration m	ageurmente: 4 positions. 5 repositions age	h		7		Gauga block measure	mont	
11.99964	Measurement repetition name		Position 2		Position 4	+	Measurements No.	Position 1		Position 3
5.31						1				
5.31							2			
5.31										
11.9991429								0.0001	0.0001	0.0001
11.9996868										
(S), 2 3.96124E-08 9.77112E-08 1.0996ZE-07 4.39686E-08 1.0996ZE-07 4.39686E-08 1.0996ZE-07 4.39686E-08 1.0996ZE-07 4.39686E-08 1.0996ZE-07 4.5455ZE-07 5.66399E-07 8.20336E-08 1.0996ZE-07 1.099					12.00002752	1				
Coverage factor (p) 95.45 %										
Coverage factor (p) 95.45 %										
Coverage factor (p) 95.45 % y 11.99974111 Degree of freedom (v _e)	y _i - y		-0.000074203	0.000732393	0.000200410					
y 11.9974111 Degree of freedom (v _e) u _e ⁴ /v _e u _{sp} 0.00026984 16 1.32546E-17 L _{messatd} 3.99906667 U _{ges} 0.000320945 3 2.21045E-16 U _{messatd} 5E-05 8 E _L U _{memp} 0 0	(y _j - y) ²	1.33083E-07	4.54552E-07	5.66399E-07	8.20336E-08	_				
Degree of freedom (v _e) U _e V _e U _{messett} 3.999066667 Degree of freedom U _{ges} 0.000320945 3 2.21045E-16 U _{messett} 5E-05 8	Coverage factor (p)	95.45	%							
Degree of freedom (v _e) U _e V _e U _{messett} 3.999066667 Degree of freedom U _{ges} 0.000320945 3 2.21045E-16 U _{messett} 5E-05 8		44.00074444	-				_	0.000050007		
U _{rrep} 0.00026984 16 1.32546E-17 L _{messald} 3.99906667 U _{geo} 0.000320945 3 2.21045E-16 U _{messald} 5E-05 Degree of freedom E _L U _{messald} 5E-05 8 Calibrated value 11.999741105 Standard uncertainty 0.000200784 k factor 2.516528348	у	11.99974111	1				E _{Lprop}	-0.000258327		
Urrep 0.00026984 16 1.32546E-17 Lmessald 3.99906667 Uges 0.000320945 3 2.21045E-16 Umessald 5E-05 Degree of freedom EL User 0 User 0 Calibrated value 11.999741105 Effective degree of freedom 6 standard uncertainty 0.000200784 k factor 2.516528348			Degree of freedom (v _e)	$1L^4/V$						
Ugeo 0.000320945 3 2.21045E-16 Umassiti Degree of freedom EL Ucor 0 0 Userp ∞ 0 Calibrated value standard uncertainty 11.999741105 k factor 2.516528348	Ureo	0.00026984	16				manueld	3.999066667		
E _L U _{corr} U _{temp} Calibrated value standard uncertainty k factor 2.516528348 10 0 Effective degree of freedom 6	-102		_				-1116.00010		Degree of freedom	
Utcor 0 0 Utcor 0 0 Calibrated value 11.999741105 Effective degree of freedom 6 standard uncertainty 0.000200784 6 k factor 2.516528348 6	Ugeo	0.000320945	3	2.21045E-16			U _{measstd}	5E-05	8	
Utcor 0 0 Utcor 0 0 Calibrated value 11.999741105 Effective degree of freedom 6 standard uncertainty 0.000200784 6 k factor 2.516528348 6	F.		7							
Userp ∞ 0 Calibrated value 11.999741105 Effective degree of freedom 6 standard uncertainty 0.000200784 6 k factor 2.516528348 6	2.		_							
Calibrated value 11.999741105 Effective degree of freedom 6 standard uncertainty 0.000200784 6 k factor 2.516528348 6	Ucorr		0	0						
Calibrated value 11.999741105 Effective degree of freedom 6 standard uncertainty 0.000200784 6 k factor 2.516528348 6	Uterro		¬ ∞	0						
standard uncertainty 0.000200784 k factor 2.516528348	- may		4	_						
standard uncertainty 0.000200784 k factor 2.516528348	Calibrated value	11 000741105	7	Effective degree of freedom		,				
k factor 2.516528348	Calibrated value	11.999741105	1	Ellective degree of freedom		_				
	standard uncertainty	0.000200784]							
	k factor	2.516529349	1							
Extended uncertainty 0.000505278	K IdCtor	2.010028348								
	Extended uncertainty	0.000505278	1							
			-]						

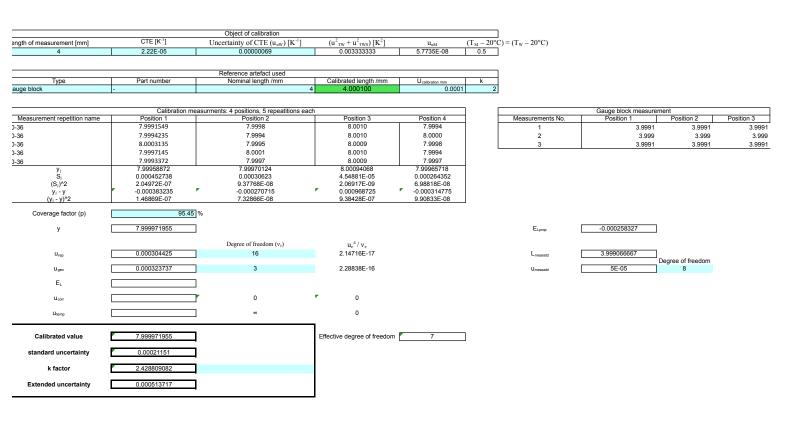
-		Object of calibration							
ength of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{ow}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS})[K^2]$	$u_{\alpha M}$	(T ₁₁ – 20°C	$(C) = (T_w - 20^{\circ}C)$			
4	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5				
	•		•		'	•			
		Reference artefact used							
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
auge block	-	4		0.000					
	•		•		•				
	Calibratian ma	asurments: 4 positions, 5 repeatitions each	h		_		Gauge block measuren	mont	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	-	Measurements No.	Position 1	Position 2	Position 3
-12	15.9996739	16.0004	16.0010	15.9998	7	1	3.9991	3.9991	3.999
-12	15.9992338	16.0001	16.0010	15.9999		2	3.999	3.999	3.99
-12	15.9993368	15.9997	16.0009	15.9999		3	3.9991	3.9991	3.999
-12	15.9993152	16.0000	16.0007	15.9998			•		
-12	16.0002997	16.0002	16.0012	15.9998					
y _i S _i	15.99957188	16.0000896	16.00094296	15.99983534					
S _j	0.000440334	0.000249247 6.21243E-08	0.000178982	7.18483E-05					
(S _j)^2 y _j - y	1.93894E-07 -0.000538065	-2.0345E-05	3.20346E-08 0.000833015	5.16217E-09 -0.000274605					
(y _i - y)^2	2.89514E-07	4.13919E-10	6.93914E-07	7.54079E-08					
	•								
Coverage factor (p)	95.45	%							
y	16.00010995					E _{Lprop}	-0.000258327		
,	10.00010000					штрюр	0.000200027		
		Degree of freedom (ve)	u_e^4 / v_e						
U _{rep}	0.000270747	16	1.34336E-17			L _{measstd}	3.999066667		
		_						Degree of freedom	
u_{geo}	0.000297104	3	1.62328E-16			U _{measstd}	5E-05	8	
E⊾									
Ucorr		0	0						
		00	0						
U _{temp}			Ü						
ll .			7						
Calibrated value	16.000109945		Effective degree of freedom	7					
standard uncertainty	0.000191647								
k factor	2.428809082								
Riddioi	2.420003002								
Extended uncertainty	0.000465473								
		ı]						
			_						

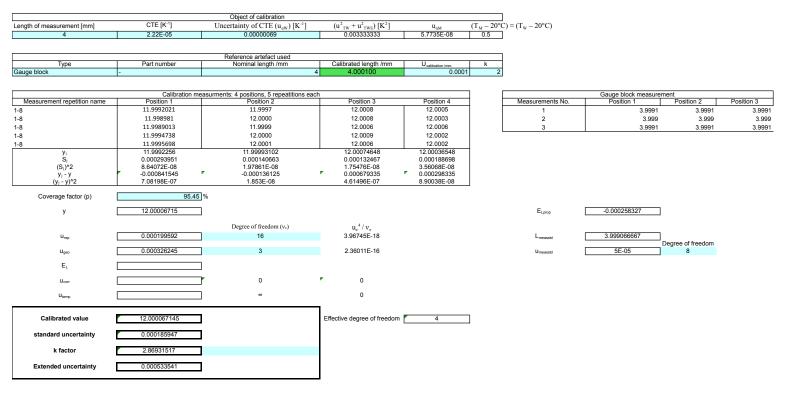


Calibrated value standard uncertainty k factor Extended uncertainty

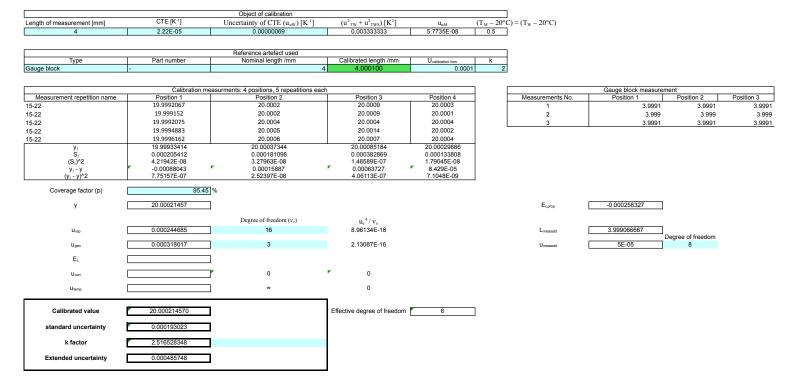
CALCULATION OF LENGTH CALIBRATION

		Object of calibration							
ength of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{aW}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS})[K^2]$	u _{aM}		$(C) = (T_W - 20^{\circ}C)$			
4	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5	l			
		Reference artefact used				1			
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
auge block -		4	4.000100	0.0001	1 2				
	0.111.11				,				
Measurement repetition name	Position 1	surments: 4 positions, 5 repeatitions each Position 2	Position 3	Position 4	+	Measurements No.	Gauge block measurement Position 1 F	Position 2	Position 3
3-24	23.9996091	23.9996	24.0006	23.9998		1	3.9991	3.9991	3.9991
3-24	23.9995351	24.0001	24.0006	24.0007		2	3.999	3.999	3.999
3-24	23.9993662	24.0004	24.0006	24.0003		3	3.9991	3.9991	3.9991
3-24	24.0001178 23.9999698	23.9999 23.9998	24.0015 24.0007	24.0003 23.9999					
3-24 V	23.9997196	23.99994326	24.0007	24.00019576	-				
y _i S _i	0.000313171	0.000295703	0.000399532	0.000347646					
(S _j)^2	9.80763E-08 -0.0004496	8.74403E-08 -0.00022594	1.59626E-07 0.00064898	1.20858E-07 2.656E-05					
y _i - y (y _i - y)^2	2.0214E-07	5.10489E-08	4.21175E-07	7.05434E-10					
Coverage factor (p)	95.45 %				-				
у	24.0001692					E _{Lprop}	-0.000258327		
		Degree of freedom (ve)	u_e^4/v_e						
U _{rep}	0.000341321	16	3.39306E-17			L _{measstd}	3.999066667		
	0.000007400	2	0.500455.47					ee of freedom	
U _{geo}	0.000237183	3	6.59315E-17			Umeasstd	5E-05	8	
E _L									
		0	0						
Ucorr		Ü	U						
U _{temp}		∞	0						
	0.4.000.400.000			40	_				
Calibrated value	24.000169200		Effective degree of freedom	13	_				
standard uncertainty	0.000193298								
li fantan .	0.044000007								
k factor	2.211800697								
Extended uncertainty	0.000427536								
		~		~					
		CALCULATION	N OF LENGT	H CALIB	BKAT.	ION			
		Object of calibration							
Length of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{aW}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	$u_{\alpha M}$		20°C) = $(T_{\text{W}} - 20^{\circ}\text{C})$			
4	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5				
		Reference artefact used				_			
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
Gauge block	-	-	4 4.000100		001	2			
Measurement repetition name	Calibration me Position 1	easurments: 4 positions, 5 repeatitions ea Position 2	Position 3	Position 4		Measurements No.	Gauge block measurem Position 1	ent Position 2	Position 3
24-30	3.9994548	3.9989	4.0009	4.0003		1	3.9991	3.9991	3.999
24-30	3.9989634	3.9996	4.0009	4.0005		2	3.999	3.999	3.99
24-30	3.9990219	3.9994	4.0008	4.0003		3	3.9991	3.9991	3.999
24-30	3.9992444	3.9991	4.0011	4.0005					
24-30	3.9992083 3.99917856	3.9992 3.99925398	4.0007 4.00087132	4.0001 4.00033934					
y _i S _j (S _j)^2	0.000195169	0.000256459	0.000174837	0.000138889					
(S _j)^2	3.8091E-08	6.57714E-08 -0.00065682	3.05679E-08	1.92903E-08 0.00042854					
y _j - y (y _j - y)^2	-0.00073224 5.36175E-07	-0.00065682 4.31413E-07	0.00096052 9.22599E-07	1.83647E-07					
Coverage factor (p)	95.45	1%							
		1 '** 1				_	0.0005		
у	3.9999108	I				E_{Lprop}	-0.000258327		
		Degree of freedom (ve)	u_e^4/v_e						
U _{rep}	0.000196036	16	3.69219E-18			L _{measstd}	3.999066667		
U ···	0.000415716	3	6.222E-16			U _{measstd}	5E-05	egree of freedom 8	
U _{geo}	0.000410710		V.LLELL-10			Umeasstd	52-00	J	
EL									
			-						





		Object of calibration				٦			
Length of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{aW}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS})[K^2]$	u_{aM}	(T = 20°	$^{\perp}C) = (T_{W} - 20^{\circ}C)$			
4	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5	7			
4	2.22E-03	0.00000069	0.00555555	5.7735E-06	0.5	_			
		Reference artefact used				٦			
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k	1			
Gauge block	- art manned	4		0.000		2			
Caage blook			1.000100	0.000	-	1			
					_				
		asurments: 4 positions, 5 repeatitions each					Gauge block measuren		
Measurement repetition name	Position 1	Position 2	Position 3	Position 4		Measurements No.	Position 1	Position 2	Position 3
8-15	15.9995625	15.9993	16.0008	16.0004		1	3.9991	3.9991	3.9991
8-15	15.9989982	15.9994	16.0008	16.0003		2	3.999	3.999	3.999
8-15	15.9987856	15.9999	16.0008	16.0002		3	3.9991	3.9991	3.9991
8-15	15.9996244	15.9994	16.0005	16.0005					
8-15	15.9994394	15.9997	16.0002	16.0003					
y _i	15.99928202	15.9995291	16.0006136	16.00033648					
y _i S _j	0.000370016	0.000253395	0.000237716	0.000129325					
(S _j)^2	1.36912E-07	6.42088E-08	5.65091E-08	1.67249E-08					
y _i - y	-0.00065828	-0.0004112	0.0000100	0.00039618					
(y _i - y)^2	4.33333E-07	1.69085E-07	4.53333E-07	1.56959E-07					
Coverage factor (p)	95.45	%							
у	15.9999403					E _{Lprop}	-0.000258327		
		Degree of freedom (v _c)	u_e^4/v_e						
U _{rep}	0.000261894	16	1.1761E-17			measstd	3.999066667	Degree of freedom	
U _{geo}	0.000317898	3	2.1277E-16			Umeasstd	5E-05	8	
EL									
Ucorr		0	0						
U _{temp}		∞	0						
			1						
Calibrated value	15.999940300		Effective degree of freedom	6					
standard uncertainty	0.00019744								
	0.510500010								
k factor	2.516528348								
Extended uncertainty	0.000496863								
			1						
		CALCIILATIO	NOFLENCT	HCALIR	RATI	ON			

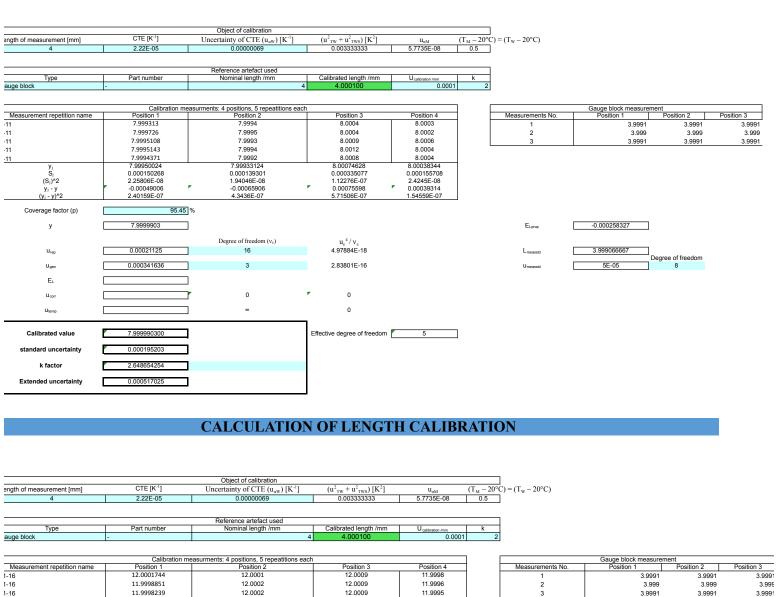


Calibrated value

standard uncertainty k factor Extended uncertainty 3.999841755

CALCULATION OF LENGTH CALIBRATION

		Object of calibration							
ength of measurement [mm]	CTE [K-1]	Uncertainty of CTE (uaw) [K-1]	$(u^2_{TW} + u^2_{TWS})[K^2]$	$u_{\alpha M}$		$T(T) = (T_W - 20^{\circ}C)$			
4	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5				
		Reference artefact used							
Type	Part number	Nominal length /mm	Calibrated length /mm 4 4.000100	U calibration /mm 0.0001	k 2				
auge block	-		4.000100	0.0001	2				
	0.171.17								
Measurement repetition name	Position 1	asurments: 4 positions, 5 repeatitions eac Position 2	Position 3	Position 4	+ +	Measurements No.	Gauge block measuren Position 1	Position 2	Position 3
2-29	23.9997215	23.9995	24.0006	23.9996	1 1	1	3.9991	3.9991	3.9
2-29	23.9998972	24.0000	24.0006	23.9997		2	3.999	3.999	3.9
2-29	23.9998773	24.0001	24.0009	23.9996		3	3.9991	3.9991	3.9
2-29	23.999848	23.9995	24.0009	23.9998					
2-29	23.999915	23.9995	24.0006	23.9994	-				
y _j S _j	23.9998518 7.69711E-05	23.99969412 0.000289136	24.00070468 0.000184008	23.99959166 0.000149358					
(S _i)^2	5.92455E-09	8.35996E-08	3.3859E-08	2.23079E-08					
y _i - y	-0.000108765	-0.000200443	0.000744115 5.53707E-07	-0.000368905					
(y _i - y)^2	1.18298E-08	7.09929E-08	5.53/U/E-U/	1.36091E-07	_				
Coverage factor (p)	95.45	%							
	23.99996057					_	-0.000258327		
у	23.99990037					E _{Lprop}	-0.000236327		
		Degree of freedom (ve)	u_e^4 / v_e						
U _{rep}	0.000190847	16	3.31654E-18			L _{measstd}	3.999066667		
	0.000050740	2	0.000005.47				55.05	Degree of freedom	
U _{geo}	0.000253742	3	8.63633E-17			U _{measstd}	5E-05	8	
E∟									
		0	r 0						
U _{corr}		0	. 0						
U _{temp}		∞	0						
			7						
Calibrated value	23.999960565		Effective degree of freedom	6	1				
					_				
standard uncertainty	0.000152908								
k factor	2.516528348								
K lactor	2.510520340								
Extended uncertainty	0.000384797								
anoth of manuscrament (mm)	CTE [K- ¹]	Object of calibration Uncertainty of CTE (u _{aw}) [K-1]	(u ² _{TW} + u ² _{TWS}) [K ²]			= (T _w - 20°C)			
ength of measurement [mm]	2.22E-05	0.00000069	0.003333333	u _{αM} (5.7735E-08	0.5	- (1 _W - 20 C)			
		Reference artefact used							
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
auge block	-	4	4.000100	0.0001	2				
					_				
Measurement repetition name	Calibration mea	surments: 4 positions, 5 repeatitions each Position 2	Position 3	Position 4		Measurements No.	Gauge block measuremer Position 1	Position 2	Position 3
9-36	3.998912	3.9991	4.0011	3.9997		1	3.9991	3.9991	3.9991
9-36	3.9983603	4.0000	4.0011	4.0003		2	3.999	3.999	3.999
9-36	3.9990022	3.9999	4.0009	3.9996		3	3.9991	3.9991	3.999
9-36	3.9982504	3.9997	4.0010	3.9999					
9-36	3.9987146 3.9986479	3.9998 3.99969758	4.0014 4.00110004	4.0001 3.9999215					
y _i S _j	0.000331831	0.00037247	0.00017032	0.000295494					
(S _j)^2	1.10112E-07	1.38734E-07	2.9009E-08	8.73166E-08					
y _i - y (y _i - y)^2	-0.001193855 1.42529E-06	-0.000144175 2.07864E-08	0.001258285 1.58328E-06	7.9745E-05 6.35927E-09					
	•		1.303201-00	J.JJ321L-U3					
Coverage factor (p)	95.45	%							
у	3.999841755					E _{Lprop}	-0.000258327		
,	5.555511100					—циор			
		Degree of freedom (v _e)	u_e^4/v_e						
U _{rep}	0.000302147	16	2.08359E-17			L _{measstd}	3.999066667	aron of front deser	
Ugeo	0.000502968	3	1.33327E-15			U _{measstd}	5E-05	gree of freedom 8	
EL									
Ucorr		0	0						

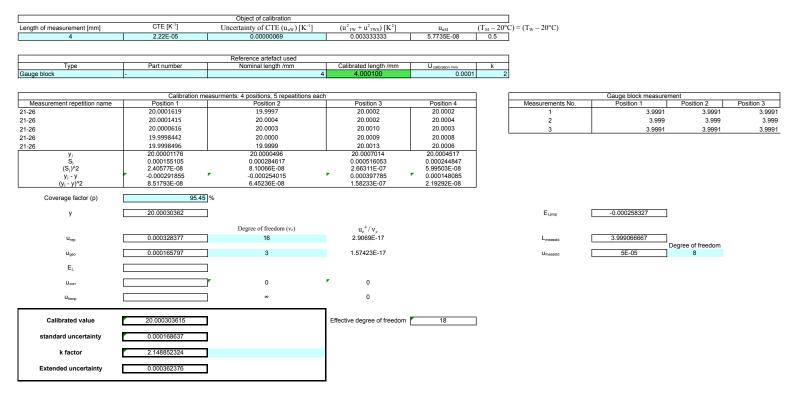


		Reference artefact used						
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k			
auge block	-	4	4.000100	0.0001	2			
		asurments: 4 positions, 5 repeatitions each			Γ		Gauge block measure	ment
Measurement repetition name	Position 1	Position 2	Position 3	Position 4		Measurements No.	Position 1	Position 2
1-16	12.0001744	12.0001	12.0009	11.9998		1	3.9991	3.9991
1-16	11.9998851	12.0002	12.0009	11.9996		2	3.999	3.999
1-16	11.9998239	12.0002	12.0009	11.9995	L	3	3.9991	3.9991
1-16	12.000004	12.0002	12.0006	11.9997				
1-16	12.0001392	12.0003	12.0012	11.9995				
y _j S _i	12.00000532	12.00019306	12.00090864	11.99961142				
S _j (S _i)^2	0.000153199 2.34699E-08	6.6452E-05 4.41587E-09	0.000180708 3.26554E-08	0.000137656 1.89493E-08				
(S _j)*2 y _j - y			0.00072903	-0.00056819				
(y _i - y)^2	3.0377E-08	1.80902E-10	5.31485E-07	3.2284E-07				
Coverage factor (p)	95.45	%						
у	12.00017961					E _{Lprop}	-0.000258327	
		Degree of freedom (v _e)	u_e^4 / ν_e					
u_{rep}	0.00014097	16	9.87301E-19			$L_{measstd}$	3.999066667	Degree of freedom
U _{geo}	0.000271551	3	1.13284E-16			U _{measstd}	5E-05	8
EL								
U _{corr}		0	0					
			•					
U _{temp}		∞	0					
Calibrated value	12.000179610		Effective degree of freedom	4				
)				
standard uncertainty	0.000149698							
k factor	2.86931517							
Extended uncertainty	0.000429532							

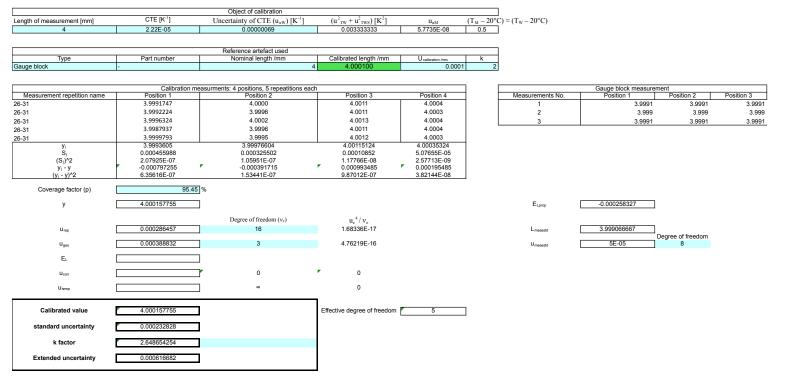
0.000506034

CALCULATION OF LENGTH CALIBRATION

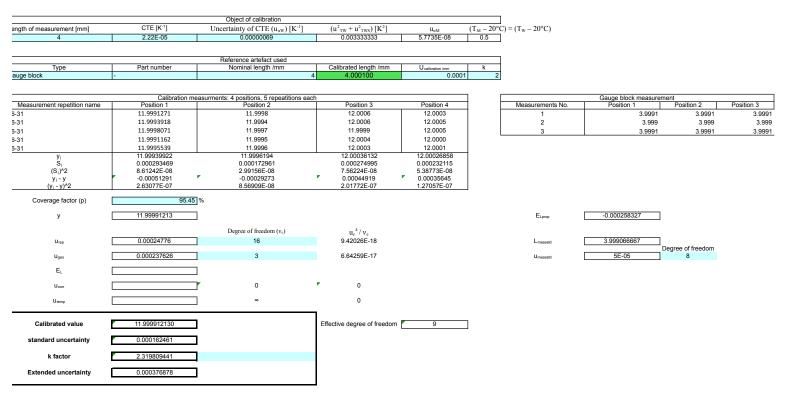
	OTE 0/41	Object of calibration	(2 . 2) 57523		(T. 2006)	(T. 2005)			
Length of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{aW}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS})[K^2]$	u _{uM}	$(T_{\rm M} - 20^{\circ}{\rm C}) =$	$(T_W - 20^{\circ}C)$			
4	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5				
		Reference artefact used							
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
Gauge block	-	4		0.000	1 2				
									
	Calibration me	asurments: 4 positions, 5 repeatitions eac	h				Gauge block measurer	nent	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4		Measurements No.	Position 1	Position 2	Position 3
16-21	15.9994744	15.9994	16.0007	16.0002		1	3.9991	3.9991	3.999
16-21	15.9993796	15.9993	16.0007	16.0003		2	3.999	3.999	3.999
16-21	15.9989969	15.9999	16.0006	16.0004		3	3.9991	3.9991	3.999
16-21	15.9989541	15.9997	16.0009	16.0001			•		
16-21	15.9989304	15.9994	16.0004	16.0001					
y _j S _i	15.99914708	15.99955614	16.00064384	16.00021552					
	0.000258819	0.000238912	0.000185755	0.000118782					
(S _j)^2	6.69874E-08 -0.000743565	5.70792E-08 -0.000334505	3.45049E-08 0.000753195	1.41092E-08 0.000324875					
y _j - y (y _i - y)^2	5.52889E-07	-0.000334505 1.11894E-07	5.67303E-07	1.05544E-07					
Coverage factor (p)	95.45	%			-				
y	15.99989065	· 				E _{Lprop}	-0.000258327		
		Degree of freedom (v _e)	4 /						
			u _e ⁴ /ν _e				0.00000007		
U _{rep}	0.000207774	16	4.65916E-18			Lmeasstd	3.999066667	Degree of freedom	
u_{geo}	0.00033387	3	2.58862E-16			U _{measstd}	5E-05	8	
EL									
U _{corr}		0	0						
U _{temp}		∞	0						
Calibrated value	15.999890645	1	Effective degree of freedom	5	7				
Calibrated value	13.333030043	l	Encouve degree or needon		_				
standard uncertainty	0.000191053								
k factor	2.648654254								



		Object of calibration				7			
ength of measurement [mm]	CTE [K-1]	Uncertainty of CTE (uaW) [K-1]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	$u_{\alpha M}$	$(T_{M} - 20^{\circ})$	$^{\circ}C) = (T_{W} - 20^{\circ}C)$			
4	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5				
-		Reference artefact used				1			
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
auge block	-	4	4.000100	0.0001	1 2	2			
-	Calibration mea	asurments: 4 positions, 5 repeatitions each	1		7		Gauge block measurer	nent	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	1	Measurements No.	Position 1	Position 2	Position 3
6-31	23.9987049	23.9991	24.0005	23.9993		1	3.9991	3.9991	3.999
5-31	23.9987345	23.9993	24.0005	23.9992		2	3.999	3.999	3.99
5-31	23.9986436	23.9998	24.0004	23.9994		3	3.9991	3.9991	3.999
6-31	23.9990719	23.9990	24.0003	23.9997					
5-31	23.999179	23.9991	24.0007	23.9999					
y _j S _i	23.99886678	23.99923292	24.00048096	23.99950374					
S _j	0.000241386 5.8267E-08	0.000324726 1.05447E-07	0.000139915 1.95763E-08	0.000297956 8.87779E-08					
(S _j)^2	-0.00065432			₹ -1.736E-05					
y _j - y (y _i - y)^2	4.28135E-07	8.30477E-08	9.21331E-07	3.0137E-10					
(9) 3) 2	•		0.210012 07	0.01072 10	_				
Coverage factor (p)	95.45	%							
.,	23.9995211					E _{Lprop}	-0.000258327		
у	23.9993211					⊏Lprop	-0.000258327		
		Degree of freedom (v _c)	u_e^4/v_e						
U _{rep}	0.000260801	16	1.15658E-17			L _{measstd}	3.999066667		
Grep	0.000200001	10	1.100002-17			∟ meassid		Degree of freedom	
U _{geo}	0.000345545	3	2.97014E-16			U _{measstd}	5E-05	8	
_									
E∟									
U _{corr}		. 0	7 0						
Corr		•	ů						
U _{temp}		∞	0						
			-						
Calibrated value	23.999521100		Effective degree of freedom	6	7				
Calibrated value	23.999521100		Ellective degree of freedom		┙				
standard uncertainty	0.000208456								
•									
k factor	2.516528348								
Extended uncertainty	0.000524584								
Extended uncertainty	0.000324304								
			•						



		Object of calibration				1			
gth of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{ow}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS})[K^2]$	u_{aM}	(T – 20°C	$(C) = (T_W - 20^{\circ}C)$			
4	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5	l (1w 20 C)			
-	2.222-00	0.0000000	0.00000000	0.1700E-00	0.0	Į.			
		2.6				i			
Туре	Part number	Reference artefact used Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
ige block	- Fait fluifiber	Nominariengur/min		0.0001					
ige block		-	4.000100	0.0001					
		easurments: 4 positions, 5 repeatitions each			1		Gauge block measurem		
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	1	Measurements No.	Position 1	Position 2	Position 3
31	7.9995388	7.9998	8.0006	7.9994		1	3.9991	3.9991	3.9991
31	7.9991834	7.9998	8.0006	7.9996		2	3.999	3.999	3.999
31	7.9997636	7.9998	8.0009	7.9993		3	3.9991	3.9991	3.9991
31	7.9995995	7.9997	8.0008	7.9996					
31	8.0001743	7.9996	8.0007	7.9995					
y _i	7.99965192	7.9997537	8.0007229	7.99945958	1				
y _i S _j	0.000360697	0.000100349	0.000144209	0.00014048					
(S _j)^2	1.30102E-07	1.00698E-08	2.07963E-08	1.97347E-08					
y _i - y		-0.000140020		-0.000437445					
(y _j - y)^2	6.00765E-08	2.05421E-08	6.8207E-07	1.91358E-07					
Coverage factor (p)	95.45	1%							
Coverage factor (p)	93.43	1 /6							
y	7.999897025	1				E _{Lprop}	-0.000258327		
		_							
		Degree of freedom (v _e)	u_e^4 / v_e						
U _{rep}	0.000212546	16	5.10212E-18			L _{measstd}	3.999066667		
								Degree of freedom	
U _{geo}	0.000281964	3	1.31685E-16			U _{measstd}	5E-05	8	
E _L		1							
EL		1							
Ucorr		P 0	0						
		-	_						
U _{temp}		∞	0						
			1						
Calibrated value	7.999897025	1	Effective degree of freedom	6	1				
		•	_		-				
standard uncertainty	0.000170033								
		<u>-</u> '							
k factor	2.516528348								
Fortanded our restrict	0.000407000	1							
Extended uncertainty	0.000427892	J							
			l .						



		Object of calibration				7			
ength of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{aw}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	u_{aM}	$(T_M - 20)$	$(C)^{\circ}C) = (T_{W} - 20^{\circ}C)$			
4	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5				
		Reference artefact used							
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k k	0			
auge block	-	4	4.000100	0.000	11	2			
					_				
Measurement repetition name	Calibration me Position 1	easurments: 4 positions, 5 repeatitions each Position 2	Position 3	Position 4	4	Measurements No.	Gauge block measurer Position 1	nent Position 2	Position 3
3-31	15.9987398	16.0000	16.0002	15.9998	1	1	3.9991	3.9991	3.9991
3-31	15.9991538	16.0001	16.0002	16.0002		2	3.999	3.999	3.999
3-31	16.0001668	16.0003	16.0007	16.0005		3	3.9991	3.9991	3.9991
3-31	15.9988088	16.0002	16.0004	16.0000					
3-31	15.9992726	15.9998	16.0007	15.9998	4				
y _i S _i	15.99922836 0.000570725	16.00008096 0.000197102	16.00044772 0.000239447	16.00004534 0.000301742					
(S _j)^2	3.25727E-07	3.88492E-08	5.7335E-08	9.10482E-08					
y _i - y	-0.000722235	0.000130365	0.000497125	9.4745E-05					
(y _j - y)^2	5.21623E-07	1.6995E-08	2.47133E-07	8.97662E-09					
Coverage factor (p)	95.45]%							
V	15.9999506	1				E_{Lprop}	-0.000258327		
у	13.5555000	J				Lprop	-0.000236327		
		Degree of freedom (ve)	u_e^4/v_e						
U _{rep}	0.000358106	16	4.11136E-17			L _{measstd}	3.999066667	D	
$u_{\rm geo}$	0.000257347] 3	9.13763E-17			U _{measstd}	5E-05	Degree of freedom 8	
E _L		1							
Lį.		J -							
U _{corr})	0						
U _{temp}		_ ∞	0						
			1						
Calibrated value	15.999950595		Effective degree of freedom	13					
standard uncertainty	0.000205438	1							
k factor	2.211800697	_							
Extended uncertainty	0.000454388	<u> </u>							
			1						
		CALCULATION	OF LENGTH	CALIRR	ATIC	N			
		CALCULATION	OF LENGTH	CALIDA	MII) 11			
		Object of calibration				1			
ength of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{aW}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	$u_{\alpha M}$	(T ₁₁ = 20°0	$(C) = (T_W - 20^{\circ}C)$			
4	2.22E-05	0.00000069	0.0033333333	5.7735E-08	0.5	l (1w 200)			
		Reference artefact used				1			
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k	1			
auge block	-	4	4.000100	0.0001	2	I			
M		asurments: 4 positions, 5 repeatitions each	D# 2	D14 /]	Manager 1 11	Gauge block measureme		Danistan 2
Measurement repetition name 3-31	Position 1 19.998977	Position 2 20.0002	Position 3 20.0001	Position 4 19.9998	-	Measurements No.	Position 1	Position 2	Position 3 3,9991
3-31 3-31	19.998977	20.0002	20.0001	19.9998		1 2	3.9991 3.999	3.9991 3.999	3.9991 3.999
5-31 3-31	19.9994446	19.9993	20.0001	19.9996		3	3.999	3.9991	3.9991
					I	<u> </u>	0.0001	0.0001	0.0001

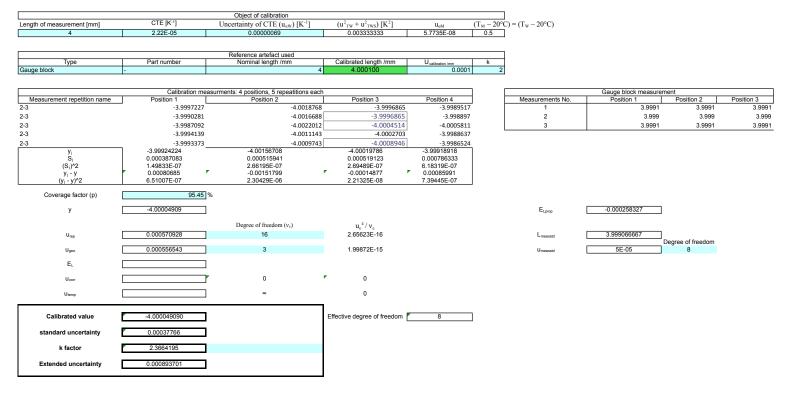
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k			
auge block	-	4	4.000100	0.0001	2			
'								
	Calibration mor	asurments: 4 positions, 5 repeatitions each	h		1		Gauge block measurer	mont
Measurement repetition name	Position 1	Position 2	Position 3	Position 4		Measurements No.	Position 1	Position 2
6-31	19.998977	20.0002	20.0001	19.9998		1	3.9991	3.9991
5-31 5-31	19.9994446	20.0004	20.0001	19.9995		2	3.999	3.999
3-31	19.9992317	19.9993	20.0001	19.9996		3	3.9991	3.9991
3-31	19.999368	20.0004	20.0006	19.9995		3	3.9991	3.9991
	19.9992713	20.0004	20.0004	19.9998				
3-31	19.99925852	20.0002	20.0004	19.99965046				
y _j S _i	0.000178008	0.00044494	0.000294003	0.000161077				
(S _j)^2	3.16869E-08	1.97972E-07	8.64378E-08	2.59457E-08				
y ₁ - y		0.000236335		-0.000201225				
(y _i - y)^2	3.51845E-07	5.58542E-08	3.11425E-07	4.04915E-08				
Coverage factor (p)	95.45	%						
	40.00005400					_	0.000050007	
У	19.99985169					E _{Lprop}	-0.000258327	
		Degree of freedom (v _e)	u_e^4/v_e					
	0.000292422	16	1.82801E-17				3.999066667	
U _{rep}	0.000292422	10	1.0200 IL-17			L _{measstd}		Degree of freedom
Ugeo	0.000251598	3	8.34804E-17			U _{measstd}	5E-05	8
_ geo						- included		
E∟								
u _{corr}		0	0					
			2					
U _{temp}		∞	0					
-			1					
Calibrated value	19.999851685		Effective degree of freedom	10				
Cumbrated Value	13.333031003		Elicetive degree of freedom	10				
standard uncertainty	0.000181459							
ounce a uncertainty	0.000101400							
k factor	2.283681613							
Extended uncertainty	0.000414395							
•								
			₫					

		Object of calibration				1			
Length of measurement [mm]	CTE [K-1]	Uncertainty of CTE (uaW) [K-1]	$(u^2_{TW} + u^2_{TWS})[K^2]$	$u_{\alpha M}$	(T _M - 20°	$C) = (T_W - 20^{\circ}C)$			
4	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5				
		Reference artefact used				1			
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
Gauge block	-		4 4.000100	0.000	1 2				
	Calibration me	easurments: 4 positions, 5 repeatitions ea	ach		7		Gauge block measurer	nent	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4		Measurements No.	Position 1	Position 2	Position 3
26-31	23.9995058	23.9993	24.0012	23.9998		1	3.9991	3.9991	3.9991
26-31	23.9995277	24.0001	24.0012	23.9995		2	3.999	3.999	3.999
26-31	23.9989355	24.0003	24.0012	23.9995		3	3.9991	3.9991	3.9991
26-31	23.9997019	23.9996	24.0008	23.9994					
26-31	24.0002655	23.9995	24.0011	23.9992					
y _i S _i	23.99958728	23.99976152	24.00109978	23.99947246					
S _j (S _i)^2	0.000476478 2.27032E-07	0.000433914 1.88281E-07	0.00015127 2.28825E-08	0.000222586 4.95444E-08					
(S _j)-2 y _j - y		-0.00021874	0.00111952	-0.0005078					
(y ₁ - y)^2	1.54433E-07	4.78472E-08	1.25333E-06	2.57861E-07					
Coverage factor (p)	95.45]%							
у	23.99998026					E _{Lprop}	-0.000258327		
		Degree of freedom (v _e)	u_r^4/v_r						
Urep	0.000349192	16	3.71703E-17			L _{measstd}	3.999066667		
		-						Degree of freedom	
u_{geo}	0.000377874	3	4.24764E-16			U _{measstd}	5E-05	8	
EL]							
Ucorr		r 0	0						
		1 ∞	0						
U _{temp}			U						
Calibrated value	23.999980260	1	Effective degree of freedom	7	7				
	20.00000203		50.10 dog.00 or 100dom	<u> </u>	_				
standard uncertainty	0.000245121								
k factor	2.428809082								
Extended uncertainty	0.000595352]							

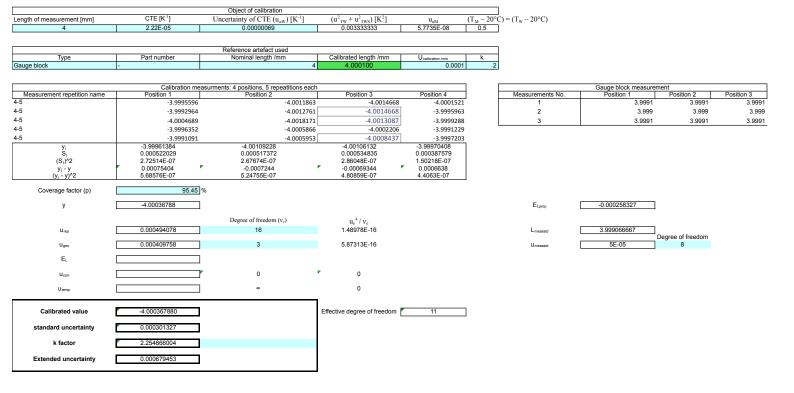
Appendix (8) Y value

CALCULATION OF LENGTH CALIBRATION

		Object of calibration				1			
gth of measurement [mm]	CTE [K-1]	Uncertainty of CTE (uaw) [K-1]	$(u^2_{TW} + u^2_{TWS})[K^2]$	u_{aM}	(T _M - 20°	$C) = (T_W - 20^{\circ}C)$			
4	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5	1 "			
						-			
		Reference artefact used				1			
Type	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
ige block	-	4	4.000100	0.0001	2				
	Calibration mea	asurments: 4 positions, 5 repeatitions each			1		Gauge block measurer		
Measurement repetition name	Position 1	Position 2	Position 3	Position 4		Measurements No.	Position 1	Position 2	Position 3
	-4.0018424	-4.0033153	-4.0003957	-4.0015622		1	3.9991	3.9991	3.999
	-4.0012022	-4.0026328	-4.0003957	-4.0011197		2	3.999	3.999	3.99
	-4.0009048	-4.0032967	-4.0011075	-4.0018444		3	3.9991	3.9991	3.999
	-4.0011478	-4.0023741	-4.001665	-4.0015724					
	-4.0005493 _	-4.0023274	-4.0010972	-4.0013226	<u>.</u>				
y _i S _i	-4.0011293	-4.00278926	-4.00093222	-4.00148426					
S _j (S _j)^2	0.000474597 2.25242E-07	0.000485892 2.36091E-07	0.000540975 2.92654E-07	0.000275037 7.56455E-08					
(S _j)-2 y _j - y	0.00045446	-0.0012055	0.00065154	9.95E-05					
(y _j - y)^2	2.06534E-07	1.45323E-06	4.24504E-07	9.90025E-09					
Coverage factor (p)	95.45	%							
у	-4.00158376					E _{Lprop}	-0.000258327		
		Degree of freedom (ve)	u_e^4 / v_e						
U _{rep}	0.000455421	16	1.07545E-16			L _{measstd}	3.999066667	Degree of freedom	
U _{geo}	0.000417749	3	6.34482E-16			U _{meassid}	5E-05	8	
EL									
Ucorr		0	0						
		œ	0						
U _{temp}		-	U						
	_		_		_				
Calibrated value	-4.001583760		Effective degree of freedom	9	_				
standard uncertainty	0.000291736								
k factor	2.319809441								
Extended uncertainty	0.000676773								
		CALCIII ATION	I OF LENIOTI	I CAT IDI		ONI			



		Object of calibration								
ength of measurement [mm]	CTE [K-1]	Uncertainty of CTE (uaw)) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	$u_{\alpha M}$	(T _M - 20°	$(C) = (T_W - 20^{\circ}C)$			
4	2.22E-05	0.0000069		0.003333333	5.7735E-08	0.5				
		Reference artefact used								
Туре	Part number	Nominal length /mm		Calibrated length /mm	U calibration /mm	k				
auge block	-		4	4.000100	0.0001	2				
Measurement repetition name	Calibration meas	urments: 4 positions, 5 repeat Position 2	titions each	Position 3	Position 4	-	Measurements No.	Gauge block measurer Position 1	ment Position 2	Position 3
4	-4.0018147		4.0025312	-4.0010428	-4.0009141	_	1	3.9991	3.9991	3.99
4	-4.0014229		4.0015556	-4.0010428	-3.9989581		2	3.999	3.999	3.9
4	-4.0015127		4.0016382	-4.000748	-4.0020755		3	3.9991	3.9991	3.99
4	-4.0017206	-	4.0015763	-4.0009828	-3.9999311					
4	-3.9995809		-4.001834	-4.0008914	-3.9991093	;				
y _j S _i	-4.00121036	-4.00182706		-4.00094156	-4.00019762	7				
S _i (S _i)^2	0.000924296 8.54324E-07	0.000408687 1.67025E-07		0.000124681 1.55453E-08	0.001306872 1.70792E-06					
y ₁ - y	-0.00016621	-0.00078291		0.00010259						
(y, - y)^2	2.76258E-08	6.12948E-07		1.05247E-08	7.16613E-07					
Coverage factor (p)	95.45 %									
у	-4.00104415						E _{Lprop}	-0.000258327		
		Degree of freedom (v _c)		u_e^4/v_e						
U _{rep}	0.000828373	16		1.17718E-15			L _{measstd}	3.999066667		
S lep							□ Interseto		Degree of freedom	
Ugeo	0.000337603	3		2.70636E-16			U _{measstd}	5E-05	8	
E∟										
Ucorr		0		0						
				0						
U _{temp}		•		U						
Calibrated value	-4.001044150		E	Effective degree of freedom	18	1				
-4	0.000407405			_		-				
standard uncertainty	0.000407105		J							
k factor	2.148852324									
Extended uncertainty	0.000874808									
	1.11117 1000									



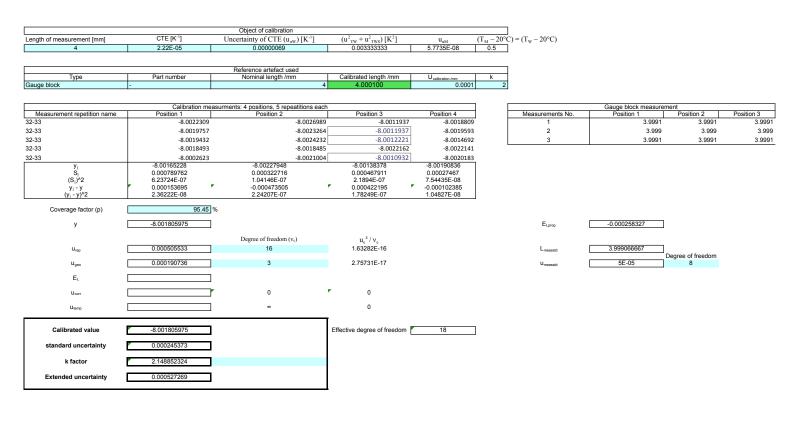
Calibrated value standard uncertainty

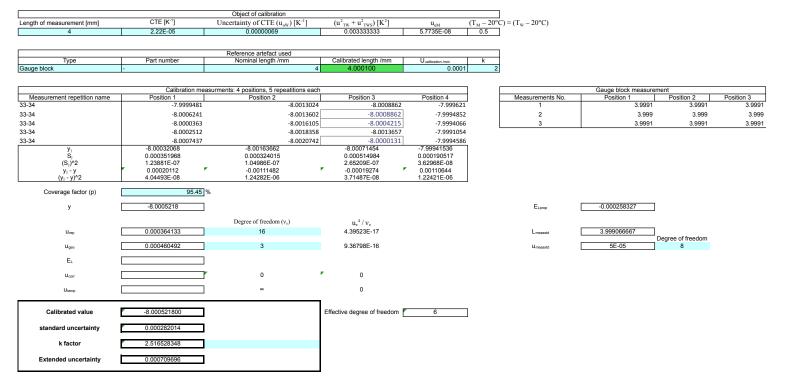
Extended uncertainty

CALCULATION OF LENGTH CALIBRATION

Length of measurement [mm]	CTE [K-1]	Object of calibration Uncertainty of CTE (u _{aW}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS})[K^2]$	u _{aM} ($T_M - 20^{\circ}C) = ($	T _w – 20°C)			
4	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5	. w /			
Туре	Part number	Reference artefact used Nominal length /mm	Calibrated length /mm	U calibration /mm	k				
Gauge block -		4	4.000100	0.0001	2				
Measurement repetition name	Calibration measu Position 1	rments: 4 positions, 5 repeatitions each Position 2	Position 3	Position 4		Measurements No.	Gauge block measurement Position 1 Pe	osition 2 F	Position 3
5-6	-4.0001436	-4.0020782	-4.0020347	-3.9994124		1	3.9991	3.9991	3.9991
5-6 5-6	-4.0001166 -4.0001282	-4.0017994 -4.0007896	-4.0020347 -4.0007507	-3.9987282 -3.9999793		2	3.999 3.9991	3.999 3.9991	3.999
5-6	-3.9992347	-4.0021428	-3.9997543	-3.9982913		3	3.5551	3.5551	3.9991
5-6	-3.9989637	-4.0021586	-4.0003385	-3.999231					
y _i S _i	-3.99971736 0.000572457	-4.00179372 0.000579701	-4.00098258 0.00102362	-3.99912844 0.000647323					
(S _j)^2	3.27707E-07 0.000688165	3.36053E-07 -0.001388195	1.0478E-06 -0.000577055	4.19028E-07 0.001277085					
y _j - y (y _j - y)^2	4.73571E-07	1.92709E-06	3.32992E-07	1.63095E-06					
Coverage factor (p)	95.45 %								
_	•						0.000050007		
у	-4.000405525					E _{Lprop}	-0.000258327		
_		Degree of freedom (v _e)	u_e^4 / v_e			_			
U _{rep}	0.000729826	16	7.0928E-16			_measstd	3.999066667 Degre	e of freedom	
u _{geo}	0.000603089	3	2.75603E-15			Umeasstd	5E-05	8	
EL [
Ucorr		0	0						
_		ŭ							
U _{temp}		œ	0						
Calibrated value	-4.000405525		Effective degree of freedom						
Calibrated value			Effective degree of freedom	11					
standard uncertainty	0.000444363								
k factor	2.254866004								
Extended uncertainty	0.001001979								
Extended uncortainty	0.001001010								
		CALCULATIO	VOFLENCT	H CAI ID	DATIC	3 B T			_
		CILECELIA							
			OF LENGT	II CALID	INAIIC	JN			
			OF LENGT	II CALID	MAII	JN			ı
			OF LENGT	II CALID	IKATIC	JN			
		Object of calibration	VOI LENGI	II CALID	OKATIC	JN			
Length of measurement [mm]	CTE [K-1]	Object of calibration $Uncertainty of CTE \left(u_{ew}\right) [K^{-1}]$	$(u^2_{\text{TW}} + u^2_{\text{TWS}})[K^2]$] C) = (T _w - 20°C)			
Length of measurement [mm]	CTE [K ⁻¹] 2.22E-05			u _{aM} 5.7735E-08]			
		Uncertainty of CTE (u _{aW}) [K ⁻¹] 0.00000069	$(u^2_{\text{TW}} + u^2_{\text{TWS}}) [K^2]$	$u_{a\mathrm{M}}$	(T _M – 20°]			
4	2.22E-05	Uncertainty of CTE (u_{aW}) [K^{-1}] 0.00000069 Reference artefact used	$\begin{array}{c} (u^2_{TW} + u^2_{TWS}) \left[K^2\right] \\ 0.003333333 \end{array}$	U _{eM} 5.7735E-08	$(T_{\rm M} - 20^{\circ})$]			
		Uncertainty of CTE (u _{aW}) [K ⁻¹] 0.00000069	$(u^2_{\text{TW}} + u^2_{\text{TWS}}) [K^2]$	$u_{a\mathrm{M}}$	(T _M - 20°0]			
4 Type	2.22E-05 Part number	Uncertainty of CTE (u_{aw}) $[K^{-1}]$ 0.00000069 Reference artefact used Nominal length /mm		U _{oM} 5.7735E-08	(T _M - 20°0]			
Type Gauge block	2.22E-05 Part number - Calibration me	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000089 Reference artefact used Nominal length /mm	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 4.000100	U _{sh} N 5.7735E-08	(T _M - 20°0] C) = (T _w - 20°C)	Gauge block measure	ement	Position 3
4 Type	2.22E-05 Part number	Uncertainty of CTE (u_{aw}) $[K^{-1}]$ 0.00000069 Reference artefact used Nominal length /mm	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 4 4.000100	U _{oM} 5.7735E-08 U _{ositization imm} 0.00	(T _M - 20°t) 0.5]	Gauge block measure Position 1 3.9991	ement Position 2 3.999°	Position 3 3.9991
Type Gauge block Measurement repetition name 31-32 31-32	2.22E-05 Part number - Calibration me Position 1 -4.0016091 -4.0015153	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000089 Reference artefact used Nominal length /mm assurments: 4 positions, 5 repeatitions ex Position 2 -4.00157 -4.00307	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 4 4.000100 ach Position 3 3 -4.001997	U _{shM} 5.7735E-08 U _{salteration imm} 0.00 Position 4 9 -3,9997 9 -3,9992	(T _M - 20°6 0.5 0.5 0.001 k 0.001 2	C) = (T _W - 20°C) Measurements No.	Position 1 3.9991 3.999	Position 2 3.999 3.999	3.9991 3.999
Type Gauge block Measurement repetition name 31-32 31-32 31-32	2.22E-05 Part number - Calibration me Position 1 -4.0016091 -4.0015153 -4.0012979	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000089 Reference artefact used Nominal length /mm asurments: 4 positions, 5 repeatitions er Position 2 -4.00157 -4.00307 -4.00205	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 4 4.000100 Position 3 3 4.001997 56 -4.001997 91 -4.001466	U _{oM} 5.7735E-08 U _{oalteration imm} 0.00 Position 4 9 -3.99972 9 -3.99922 2 -3.9997	(T _M - 20°4 0.5	C) = (T _w - 20°C) Measurements No.	Position 1 3.9991	Position 2 3.9991	3.9991 3.999
Type Gauge block Measurement repetition name 31-32 31-32 31-32 31-32	2.22E-05 Part number - Calibration me Position 1 -4.0016091 -4.0015153	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000089 Reference artefact used Nominal length /mm assurments: 4 positions, 5 repeatitions ex Position 2 -4.00157 -4.00307	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 4	U _{calthration imm} U _{calthration imm} U _{calthration imm} 0.00 Position 4 9 -3.99976 3.9992 -3.9992 -3.9995 -3.99982	(T _M - 20°(0.5) 0.5 001 k 0001 2	C) = (T _W - 20°C) Measurements No.	Position 1 3.9991 3.999	Position 2 3.999 3.999	3.9991 3.999
Type Gauge block Measurement repetition name 31-32 31-32 31-32 31-32 31-32 31-32	2.22E-05 Part number Calibration me Position 1 -4.0016091 -4.0015153 -4.0012979 -3.999412 -3.9990116 -4.00057518	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000089 Reference artefact used Nominal length /mm asurments: 4 positions, 5 repeatitions er Position 2 -4.00157 -4.00207 -4.00201438 -4.00201438	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 4 4.000100 Ch Position 3 3 -4.00199; 66 -4.00199; 11 -4.001466; 67 -3.99981; 99 -4.002319	U _{calthration imm} 5.7735E-08 U _{calthration imm} 0.00	(T _M - 20°(0.5) 0.5 001 k 0001 2	C) = (T _W - 20°C) Measurements No.	Position 1 3.9991 3.999	Position 2 3.999 3.999	3.9991 3.999
Type Gauge block Measurement repetition name 31-32 31-32 31-32 31-32 31-32 31-32 S _j	2.22E-05 Part number - Calibration me Position 1 -4.0016913 -4.0015913 -4.0012979 -3.999412 -3.999416 -4.00057518 0.001245393 1.551E-06	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000089 Reference artefact used Nominal length /mm asurments: 4 positions, 5 repeatitions er Position 2 -4.00157 -4.00207 -4.00201438 0.000621937 3.86805E-07	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 4 4.000100 Position 3 3 -4.001997 56 -4.001997 51 -4.001466 57 -3.99811 90.000918338 8.39675E-07	U _{calibration imm} U _{calibration imm} U _{calibration imm} O.00 Position 4 9	(T _M - 20°(0.5) 0.5 001 k 0001 2	C) = (T _W - 20°C) Measurements No.	Position 1 3.9991 3.999	Position 2 3.999 3.999	3.9991 3.999
Type Gauge block Measurement repetition name 31-32 31-32 31-32 31-32 31-32 31-32 31-32 y ₁ S ₁ S ₁ (S ₁) ² y ₁ y ₁ y	2.22E-05 Part number Calibration me Position 1	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000089 Reference artefact used Nominal length /mm asurments: 4 positions, 5 repeatitions et Position 2 -4.00157 -4.00307 -4.00201438 0.000621937 3.86805E-07 -0.001280185	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 4 4.000100 Ich Position 3 3 -4.001997 31 -4.001496 57 -3.999813 39 -4.0012319 0.000916338 8.39675E-07 -0.000497705	U _{salt} 5.7735E-08 U _{salteration imm} 0.00 Position 4 9 -3.99976 2 -3.99925 5 -3.99826 2 -3.99876 -3.99827 7 -0.001618875	(T _M - 20°(0.5) 0.5 001 k 0001 2	C) = (T _W - 20°C) Measurements No.	Position 1 3.9991 3.999	Position 2 3.999 3.999	3.9991 3.999
Type Gauge block Measurement repetition name 31-32 31-32 31-32 31-32 31-32 31-32 31-32 31-32 31-32	2.22E-05 Part number - Calibration me Position 1 -4.0016091 -4.0015153 -4.0012979 -3.999412 -3.999416 -4.0005718 0.001245393 1.551E-06 0.000159015 2.52858E-08	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000089 Reference artefact used Nominal length /mm asurments: 4 positions, 5 repeatitions er Position 2 -4.00157 -4.00307 -4.00207 -4.00205 -4.00170 -4.00201438 0.000621937 3.86805E-07 -0.001260185 1.63887E-06	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 4 4.000100 Position 3 3 -4.001997 56 -4.001997 51 -4.001466 57 -3.99811 90.000918338 8.39675E-07	U _{calibration imm} U _{calibration imm} U _{calibration imm} O.00 Position 4 9	(T _M - 20°(0.5) 0.5 001 k 0001 2	C) = (T _W - 20°C) Measurements No.	Position 1 3.9991 3.999	Position 2 3.999 3.999	3.9991 3.999
Type Gauge block Measurement repetition name 31-32 31-32 31-32 31-32 31-32 31-32 31-32 y ₁ S ₁ S ₁ (S ₁) ² y ₁ y ₁ y	2.22E-05 Part number Calibration me Position 1	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000089 Reference artefact used Nominal length /mm asurments: 4 positions, 5 repeatitions er Position 2 -4.00157 -4.00307 -4.00207 -4.00205 -4.00170 -4.00201438 0.000621937 3.86805E-07 -0.001260185 1.63887E-06	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 4 4.000100 Ich Position 3 3 -4.001997 31 -4.001496 57 -3.999813 39 -4.0012319 0.000916338 8.39675E-07 -0.000497705	U _{salt} 5.7735E-08 U _{salteration imm} 0.00 Position 4 9 -3.99976 2 -3.99925 5 -3.99826 2 -3.99876 -3.99827 7 -0.001618875	(T _M - 20°(0.5) 0.5 001 k 0001 2	C) = (T _W - 20°C) Measurements No.	Position 1 3.9991 3.999	Position 2 3.999 3.999	3.9991 3.999
Type Gauge block Measurement repetition name 31-32 31-32 31-32 31-32 31-32 31-32 31-32 31-32 31-32	2.22E-05 Part number - Calibration me Position 1 -4.0016091 -4.0015153 -4.0012979 -3.999412 -3.999416 -4.0005718 0.001245393 1.551E-06 0.000159015 2.52858E-08	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000089 Reference artefact used Nominal length /mm asurments: 4 positions, 5 repeatitions er Position 2 -4.00157 -4.00307 -4.00207 -4.00205 -4.00170 -4.00201438 0.000621937 3.86805E-07 -0.001260185 1.63887E-06	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 4 4.000100 Ich Position 3 3 -4.001997 31 -4.001496 57 -3.999813 39 -4.0012319 0.000916338 8.39675E-07 -0.000497705	U _{salt} 5.7735E-08 U _{salteration imm} 0.00 Position 4 9 -3.99976 2 -3.99925 5 -3.99826 2 -3.99876 -3.99827 7 -0.001618875	(T _M - 20°(0.5) 0.5 001 k 0001 2	C) = (T _W - 20°C) Measurements No.	Position 1 3.9991 3.999	Position 2 3.999 3.999	3.9991 3.999
Type Gauge block Measurement repetition name 31-32 31-32 31-32 31-32 31-32 31-32 31-32 Coverage factor (p)	2.22E-05 Part number - Calibration me Position 1 -4.0016091 -4.0015153 -4.0012979 -3.9990116 -4.00057518 0.001245393 1.551E-06 0.000159015 2.52858E-08	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000089 Reference artefact used Nominal length /mm asurments: 4 positions, 5 repeatitions er Position 2 -4.00157 -4.00307 -4.00207 -4.00205 -4.00170 -4.00201438 0.000621937 3.86805E-07 -0.001260185 1.63887E-06	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 4 4.000100 Ch Position 3 33 -4.001997 56 -4.001997 57 -3.999811 0.000916338 8.39675E-07 0.000497705 2.4771E-07	U _{salt} 5.7735E-08 U _{salteration imm} 0.00 Position 4 9 -3.99976 2 -3.99925 5 -3.99826 2 -3.99876 -3.99827 7 -0.001618875	(T _M - 20°(0.5) 0.5 001 k 0001 2	C) = (T _w - 20°C) Measurements No. 1 2 3	Position 1 3.9991 3.9991 3.9991	Position 2 3.999 3.999	3.9991 3.999
Type Gauge block Measurement repetition name 31-32 31-32 31-32 31-32 31-32 31-32 31-32 Coverage factor (p)	2.22E-05 Part number - Calibration me Position 1 -4.0016091 -4.0015153 -4.0012979 -3.9990116 -4.00057518 0.001245393 1.551E-06 0.000159015 2.52858E-08	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000089 Reference artefact used Nominal length /mm asurments: 4 positions, 5 repeatitions er Position 2 -4.00157 -4.00307 -4.00201-7 -4.0016 -4.00170 -4.00170 -4.00170 -4.00180180	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 4 4.000100 Ich Position 3 3 -4.001997 31 -4.001496 57 -3.999813 39 -4.0012319 0.000916338 8.39675E-07 -0.000497705	U _{salt} 5.7735E-08 U _{salteration imm} 0.00 Position 4 9 -3.99976 2 -3.99925 5 -3.99826 2 -3.99876 -3.99827 7 -0.001618875	(T _M - 20°(0.5) 0.5 001 k 0001 2	C) = (T _w - 20°C) Measurements No. 1 2 3	Position 1 3.9991 3.9991 3.9991	Position 2 3.999 3.999 3.999	3.991 3.999 3.9991
Type Gauge block Measurement repetition name 31-32 31-32 31-32 31-32 31-32 31-32 Y ₁ S ₁ (S ₁)*2 Y ₁ -Y)*2 Coverage factor (p) y U _{mp}	2.22E-05 Part number Calibration me Position 1	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000089 Reference artefact used Nominal length /mm asurments: 4 positions, 5 repeatitions er Position 2 -4.00157 -4.00307 -4.00207 -4.00205 -4.00170 -4.00201438 0.000621937 3.86806E-07 -0.001260185 1.63887E-06	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 4.000100 Ich Position 3 -4.00199 -4.00196 -4.001466 -4.001466 -4.00189 -4.0012319 0.000916338 8.39675E-07 -0.000497705 2.4771E-07	U _{salt} 5.7735E-08 U _{salteration imm} 0.00 Position 4 9 -3.99976 2 -3.99925 5 -3.99826 2 -3.99876 -3.99827 7 -0.001618875	(T _M - 20°(0.5) 0.5 001 k 0001 2	C) = (T _w - 20°C) Measurements No. 1 2 3 ELgrop Lmessand	Position 1 3.9991 3.9991 3.9991 -0.000258327	Position 2 3.999 3.999	3.991 3.999 3.9991
Type Gauge block Measurement repetition name 31-32 31-32 31-32 31-32 31-32 31-32 Y ₁ S ₁ (S ₁) ² Y ₁ - Y) ² Coverage factor (p) y u _{mp} u _{geo}	2.22E-05 Part number Calibration me Position 1	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000089 Reference artefact used Nominal length /mm asurments: 4 positions, 5 repeatitions er Position 2 -4.00157 -4.00307 -4.00207 -4.00207 -4.00167 -4.00170 -4.00185 1.63887E-06 %	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 4	U _{salt} 5.7735E-08 U _{salteration imm} 0.00 Position 4 9 -3.99976 2 -3.99925 5 -3.99826 2 -3.99876 -3.99827 7 -0.001618875	(T _M - 20°(0.5) 0.5 001 k 0001 2	C) = (T _w - 20°C) Measurements No. 1 2 3	Position 1 3.9991 3.9991 3.9991 -0.000258327	Position 2 3.999 3.999 3.999	3.991 3.999 3.9991
Type Gauge block Measurement repetition name 31-32 31-32 31-32 31-32 31-32 31-32 Y ₁ S ₁ (S ₁)*2 Y ₁ -Y)*2 Coverage factor (p) y U _{mp}	2.22E-05 Part number Calibration me Position 1	Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000089 Reference artefact used Nominal length /mm asurments: 4 positions, 5 repeatitions er Position 2 -4.00157 -4.00307 -4.00207 -4.00207 -4.00167 -4.00170 -4.00185 1.63887E-06 %	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 4	U _{salt} 5.7735E-08 U _{salteration imm} 0.00 Position 4 9 -3.99976 2 -3.99925 5 -3.99826 2 -3.99876 -3.99827 7 -0.001618875	(T _M - 20°(0.5) 0.5 001 k 0001 2	C) = (T _w - 20°C) Measurements No. 1 2 3 ELgrop Lmessand	Position 1 3.9991 3.9991 3.9991 -0.000258327	Position 2 3.999 3.999 3.999	3.991 3.999 3.9991

Effective degree of freedom





Calibrated value standard uncertainty k factor

CALCULATION OF LENGTH CALIBRATION

Length of measurement [mm]	CTE [K-1]	Object of calibration Uncertainty of CTE (u _{qW}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS})[K^2]$	$u_{\alpha M}$	(T _M – 20°C	C) = (T _w – 20°C)			
4	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5	l (-w)			
Туре	Part number	Reference artefact used Nominal length /mm	Calibrated length /mm	U calibration /mm	l k				
Gauge block	-	4	4.000100	0.0001	2				
					_				
Measurement repetition name	Calibration meas Position 1	urments: 4 positions, 5 repeatitions each Position 2	Position 3	Position 4	-	Measurements No.	Gauge block measu Position 1	rement Position 2	Position 3
34-35	-8.0008262	-8.0025324	-8.0002921	-8.0003697		1	3.999	1 3.999	1 3.9
34-35	-7.9998001	-8.0011455	-8.0002921	-8.0001841		2	3.99		
34-35 34-35	-8.0001518 -8.0004591	-8.0006287 -8.0014876	-8.0005491 -8.0010034	-8.0006771 -8.0003563		3	3.999	1 3.999	1 3.9
34-35	-8.0000646	-8.0019752	-8.0012358	-7.9999943					
y _j S _i	-8.00026036 0.000394214	-8.00155388 0.00073521	-8.0006745 0.000427615	-8.0003163 0.000252878]				
(S _j)^2	1.55405E-07	5.40534E-07	1.82854E-07	6.39473E-08					
y _j - y (y _j - y)^2	0.0004409 1.94393E-07	-0.00085262 7.26961E-07	2.676E-05 7.16098E-10	0.00038496 1.48194E-07					
		7.2000 TE-07	7.10030E-10	1.401042-01	_				
Coverage factor (p)	95.45 %								
y	-8.00070126					E_{Lprop}	-0.000258327		
		Degree of freedom (v _e)	u_e^4/v_e						
U _{rep}	0.000485474	16	1.38869E-16			L _{measstd}	3.999066667	7	
	0.000298645	3	1.65721E-16			U _{measstd}	5E-05	Degree of freedon 8	1
u_{geo}	0.000230040	ű	1.007212-10			O measstd	3E-03	_	
EL									
U _{corr}		0	0						
U _{temp}		80	0						
Calibrated value	-8.000701260		Effective degree of freedom	15	7				
atandard uncertainty	0.000263504		_		-				
standard uncertainty	0.000263304								
k factor	2.181165682								
Extended uncertainty	0.000574745								
		CALCULATION Object of calibration							
Length of measurement [mm]	CTE [K-1] 2.22E-05	Uncertainty of CTE (u _{aW}) [K ⁻¹] 0.00000069	$(u^2_{TW} + u^2_{TWS}) [K^2]$ 0.003333333	u _{aM} (7 5.7735E-08	$\frac{\Gamma_{\rm M} - 20^{\circ}\text{C}}{0.5}$	$= (T_W - 20^{\circ}C)$			
		Reference artefact used							
Type Gauge block	Part number	Nominal length /mm 4	Calibrated length /mm 4.000100	U _{calibration /mm} 0.0001	k 2				
	<u> </u>								
		urments: 4 positions, 5 repeatitions each					Gauge block measureme		
Measurement repetition name 35-36	Position 1 -8.0012585	Position 2 -8.0015816	Position 3 -8.0017031	Position 4 -8.0013681	_	Measurements No.	Position 1 3.9991	Position 2 3.9991	Position 3 3.9991
35-36	-8.0010929	-8.001083	-8.0017031	-8.000948		2	3.999	3.999	3.999
35-36	-8.0010064	-8.0012434	-8.0001132	-8.0008025		3	3.9991	3.9991	3.9991
35-36 35-36	-8.0009733 -8.000804	-8.0011226 -8.0013424	-8.0017929 -8.0008482	-8.0007215 -7.9999396					
y _j S _j	-8.00102702	-8.0012746	-8.0012321	-8.00075594					
S _j (S _j)^2	0.000166562 2.7743E-08	0.000199771 3.99085E-08	0.000734421 5.39374E-07	0.00051995 2.70348E-07					
y, - y	4.5395E-05	-0.000202185	-0.000159685	0.000316475					
(y _i - y)^2	2.06071E-09	4.08788E-08	2.54993E-08	1.00156E-07					
Coverage factor (p)	95.45 %								
у	-8.001072415					E _{Lprop}	-0.000258327		
		Degree of freedom (ve)	u_e^4/ν_e						
$u_{\rm rep}$	0.000468341	16	1.20279E-16			$L_{measstd}$	3.999066667		
U _{geo}	0.000118531	3	4.11232E-18			U _{measstd}	5E-05	gree of freedom 8	
EL									
		0	٥						
Ucorr		0	0						

Effective degree of freedom 18

Extended uncertainty

		Object of calibration]			
Length of measurement [mm]	CTE [K-1]	Uncertainty of CTE (uaW) [K-1]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	$u_{\alpha M}$	$(T_{\rm M} - 20^{\circ})$	$(C) = (T_w - 20^{\circ}C)$			
4	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5]			
		Reference artefact used				1			
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k	1			
Gauge block	-	4	4.000100	0.0001	2				
	Calibration me	asurments: 4 positions, 5 repeatitions each			1		Gauge block measurer	ment	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	1	Measurements No.	Position 1	Position 2	Position 3
1-7	-8.0015853	-8.0024484	-8.0012707	-8.0014061	-	1	3.9991	3.9991	3.999
1-7	-8.0021669	-8.0015468	-8.0012707	-8.0016574		2	3.999	3.999	3.99
1-7	-8.0017152	-8.0010939	-8.0004091	-8.0014788		3	3.9991	3.9991	3.999
1-7	-8.0010588	-8.001956	-8.0015952	-8.0010458			•		
1-7	-7.9996857	-8.0017773	-8.0007331	-8.0005906					
y _i S _i	-8.00124238	-8.00176448	-8.00105576	-8.00123574	1				
Sj	0.000955621	0.000500413	0.000475834	0.000423728					
(S _j)^2	9.13211E-07	2.50413E-07	2.26418E-07	1.79545E-07					
y _i - y (y _i - y)^2	8.221E-05 6.75848E-09	-0.00043989 1.93503E-07	0.00026883 7.22696E-08	8.885E-05 7.89432E-09					
(y ₁ - y) · 2	0.73646E-09	1.93503E-07	7.22090E-08	7.09432E-09	J				
Coverage factor (p)	95.45	%							
	0.00400450					_	0.000050007		
у	-8.00132459					E _{Lprop}	-0.000258327		
		Degree of freedom (v _c)	u_e^4/v_e						
Urep	0.000626416	16	3.84938E-16			L _{measstd}	3.999066667		
Siep	0.000020110	10	0.010002 10			-meassu		Degree of freedom	
u_{geo}	0.000152869	3	1.13771E-17			U _{measstd}	5E-05	8	
EL									
Ucorr		0	0						
Geor		0							
U _{temp}		œ	0						
Calibrated value	-8.001324590		Effective degree of freedom	17	1				
Cambrated value	-0.001324390		Elicolive degree of freedom		1				
standard uncertainty	0.000290382								
k factor	2.158263401								

Calibrated value

standard uncertainty

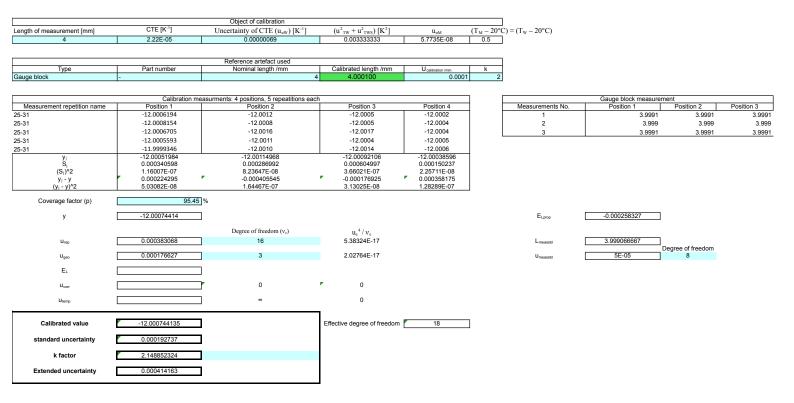
Extended uncertainty

CALCULATION OF LENGTH CALIBRATION

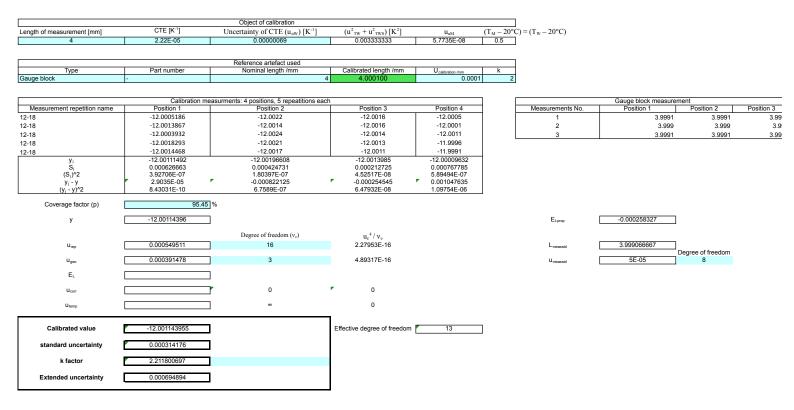
		Object of calibration							
Length of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{aW}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	$u_{\alpha M}$	(T _M – 20°C	$(T_W - 20^{\circ}C)$			
4	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5	ĺ			
		Deference externat used							
Туре	Part number	Reference artefact used Nominal length /mm	Calibrated length /mm	U calibration /mm	k				
Gauge block	-	4	4.000100	0.0001	2				
	Calibration mea	asurments: 4 positions, 5 repeatitions each			1 1		Gauge block measuren	nent	
Measurement repetition name 7-13	Position 1 -8.0009897	Position 2 -8.0019044	Position 3 -8.0021947	Position 4 -8.0008224]	Measurements No.	Position 1 3.9991	Position 2 3.9991	Position 3 3.99
7-13	-8.0011848	-8.0007559	-8.0021947	-8.0010328		2	3.999	3.999	3.99
7-13	-8.0010271	-8.0007842	-8.0006896	-8.0009663		3	3.9991	3.9991	3.99
7-13 7-13	-8.001122 -8.0009814	-8.0013103 -8.0019433	-8.001729 -7.9998689	-8.0000346 -7.999898					
У ₁ S ₁	-8.001061	-8.00133962	-8.00133538	-8.00055082	1				
S _j (S _j)^2	8.89051E-05 7.90413E-09	0.000577383 3.33372E-07	0.001024621 1.04985E-06	0.000541143 2.92835E-07					
y _i - y	1.0705E-05	-0.000267915	-0.000263675	0.000520885					
(y _i - y)^2	1.14597E-10	7.17784E-08	6.95245E-08	2.71321E-07	J				
Coverage factor (p)	95.45	%							
у	-8.001071705					E _{Lprop}	-0.000258327		
		Degree of freedom (ve)	${u_e}^4/\nu_e$						
U _{rep}	0.000648837	16	4.43081E-16			L _{measstd}	3.999066667		
U _{geo}	0.000185459	3	2.4646E-17			U _{measstd}	5E-05	Degree of freedom 8	
EL									
		0	0						
Ucorr		0							
U _{temp}		œ	0						
Calibrated value	-8.001071705		Effective degree of freedom	18	1				
			Elicolive degree of freedom [10	1				
standard uncertainty	0.000304625								
k factor	2.148852324								
Extended uncertainty	0.000654595								
Extended uncertainty									
Extended uncertainty									
Extended uncertainty		CALCULATION	OF LENGTH	CALIBR	ATIC)N			
Extended uncertainty		CALCULATION	OF LENGTH	CALIBR	ATIO)N			
Extended uncertainty		CALCULATION	OF LENGTH	CALIBR	ATIO)N			
Extended uncertainty		CALCULATION (OF LENGTH	CALIBR	ATIC	ON			
	0.000654595	Object of calibration							
ength of measurement [mm]	0.000654595 CTE [K-3]	Object of calibration $Uncertainty of CTE \left(u_{aw}\right) \left[K^{-1}\right]$	$(u_{TW}^2 + u_{TWS}^2)[K^2]$	${ m u}_{ m uM}$	(T _M – 20°C)N C) = (T _w - 20°C)			
	0.000654595	Object of calibration							
ength of measurement [mm]	0.000654595 CTE [K ⁻¹] 2.22E-05	Object of calibration $ \begin{aligned} & \text{Object of calibration} \\ & \text{Uncertainty of CTE} \left(u_{aw}\right)\left[K^{-1}\right] \\ & & \text{0.00000069} \end{aligned} $ Reference artefact used	$(u^{2}_{TW}+u^{2}_{TWS})\left[K^{2}\right]$ 0.0033333333	U _{nM} 5.7735E-08	(T _M – 20°C				
ength of measurement [mm] 4 Type	0.000654595 CTE [K-3]	Object of calibration Uncertainty of CTE $(u_{\rm ew})$ $[K^{-1}]$ 0.00000069	$(u_{TW}^2 + u_{TWS}^2)[K^2]$	${ m u}_{ m uM}$	(T _M – 20°C				
ength of measurement [mm]	0.000654595 CTE [K ⁻¹] 2.22E-05	Object of calibration $ \begin{aligned} & \text{Uncertainty of CTE} \left(u_{aw} \right) \left[K^{-1} \right] \\ & 0.00000069 \end{aligned} $ Reference artefact used Nominal length /mm	$ \frac{\left(u^2_{ TW} + u^2_{ TWS}\right)\left[K^2\right]}{0.003333333} $ Calibrated length /mm	U _{shM} 5.7735E-08 U _{calibration /mm}	(T _M – 20°C				
ength of measurement [mm] 4 Type Gauge block	0.000654595 CTE [K-1] 2.22E-05 Part number - Calibration meas	Object of calibration Uncertainty of CTE (u_aw) [K^-1] 0.00000069 Reference artefact used Nominal length /mm 4	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 4.000100	U _{nM} 5.7735E-08 U calibration //rm 0.0001	(T _M – 20°C	$(T_{\rm W} - 20^{\circ}{\rm C})$	Gauge block measurer	nent	
ength of measurement [mm] 4 Type Sauge block Measurement repetition name	0.000654595 CTE [K-1] 2.22E-05 Part number Calibration meas	Object of calibration Uncertainty of CTE (u_{aw}) $[K^{-1}]$ 0.0000069 Reference artefact used Nominal length /mm 4	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 4.000100 Position 3	U _{shM} 5.7735E-08 U _{salthration /mm} 0.0001 Position 4	(T _M – 20°C	$C = (T_W - 20^{\circ}C)$ $Measurements No.$	Position 1	Position 2	Position 3
Length of measurement [mm] 4 Type Sauge block Measurement repetition name 3-19 3-19	0.000654595 CTE [K-1] 2.22E-05 Part number - Calibration meas Position 1 -12.0019917 -12.0009418	Object of calibration Uncertainty of CTE (u_aw) [K^-1] 0.00000069 Reference artefact used Nominal length /mm 4 surments: 4 positions, 5 repeatitions each Position 2 -12.0033 -12.0021	(u² _{TW} + u² _{TWS}) [K²] 0.003333333 Calibrated length /mm 4.000100 Position 3 -12.0005 -12.0005	U _{salteration //rm} U calteration //rm 0.0001 Position 4 -12.0013 -12.0008	(T _M – 20°C	$C) = (T_w - 20^{\circ}C)$ Measurements No. 1 2	Position 1 3.9991 3.999	Position 2 3.9991 3.999	3.99 3.9
Length of measurement [mm] 4 Type Gauge block Measurement repetition name 3-19 3-19 3-19	0.000654595 CTE [K ⁻¹] 2.22E-05 Part number - Calibration meas Position 1 12.0019917 12.0099418 12.0014118	Object of calibration Uncertainty of CTE (u_w) [K-1] 0.0000069 Reference artefact used Nominal length /mm 4 surments: 4 positions, 5 repeatitions each Position 2 -12.0033 -12.0021 -12.0026	(u ² _{TW} + u ² _{TWS}) [K ²] 0.0033333333 Calibrated length /mm 4.000100 Position 3 -12.0005 -12.0005 -12.0013	U _{salbration imm} U _{salbration imm} 0.0001 Position 4 -12.0013 -12.0008 -12.0009	(T _M – 20°C	$(T_{\rm W}-20^{\circ}{\rm C})$ Measurements No.	Position 1 3.9991	Position 2 3.9991	3.99
Type Sauge block Measurement repetition name 3-19 3-19 3-19 3-19	0.000654595 CTE [K*] 2.22E-05 Part number - Calibration meas Position 1 -12.0019917 -12.0099418 -12.0014118 -12.0015468	Object of calibration Uncertainty of CTE (u_w) [K-1] 0.0000069 Reference artefact used Nominal length /mm 4 surments: 4 positions, 5 repeatitions each Position 2 -12.0023 -12.0021 -12.0026 -12.0022	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 4.000100 Position 3 -12.0005 -12.0005 -12.0013 -12.0019	U _{salbration imm} 5.7735E-08 U _{calbration imm} 0.0001 Position 4 -12.0013 -12.0009 -12.00014	(T _M – 20°C	$C) = (T_w - 20^{\circ}C)$ Measurements No. 1 2	Position 1 3.9991 3.999	Position 2 3.9991 3.999	3.99 3.9
Length of measurement [mm] 4 Type Sauge block Measurement repetition name 3-19 3-19 3-19 3-19 3-19	0.000654595 CTE [K¹] 2.22E-05 Part number - Calibration meas Position 1 -12.0019917 -12.0019418 -12.0014118 -12.0015468 -12.0003973 -12.00125788	Object of calibration Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.0000069 Reference artefact used Nominal length /mm 4 surments: 4 positions, 5 repeatitions each Position 2 -12.0023 -12.0021 -12.0026 -12.0022 -12.00222 -12.0024526	(u ² _{TW} + u ² _{TWS}) [K ²] 0.0033333333 Calibrated length /mm 4.000100 Position 3 -12.0005 -12.0005 -12.0013 -12.0011 -12.0014 -12.0011411	U _{salthration imm} 5.7735E-08 U _{calthration imm} 0.0001 Position 4 -12.0013 -12.0009 -12.0014 -12.00103642	(T _M – 20°C	$C) = (T_w - 20^{\circ}C)$ Measurements No. 1 2	Position 1 3.9991 3.999	Position 2 3.9991 3.999	3.99 3.9
Length of measurement [mm] 4 Type Sauge block Measurement repetition name 3-19 3-19 3-19 3-19 S _I	0.000654595 CTE [K-1] 2.22E-05 Part number - Calibration meas Position 1 -12.0019917 -12.0019418 -12.001418 -12.0015468 -12.00125788 0.000609541	Object of calibration Uncertainty of CTE (u_aw) [K^-1] 0.00000069 Reference artefact used Nominal length /mm 4 surments: 4 positions, 5 repeatitions each Position 2 -12,0023 -12,0021 -12,0026 -112,0022 -12,0022 -12,0022 -12,00245826 0.000491934	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 4.000100 Position 3 -12.0005 -12.0005 -12.0013 -12.0019 -12.0014 -12.0011141 0.000630278	U _{salbration from} 5.7735E-08 U _{salbration from} 0.0001 Position 4 -12.0013 -12.0008 -12.0008 -12.0009 -12.00103642 -0.000333939	(T _M – 20°C	$C) = (T_w - 20^{\circ}C)$ Measurements No. 1 2	Position 1 3.9991 3.999	Position 2 3.9991 3.999	3.99 3.9
Length of measurement [mm] 4 Type Sauge block Measurement repetition name 3-19 3-19 3-19 3-19 3-19 3-19 3-19 3-19	0.000654595 CTE [K-1] 2.22E-05 Part number - Calibration meas Position 1 -12.001917 -12.0009418 -12.00140118 -12.0015468 -12.003973 -12.00125788 0.000609541 3.71541E-07 0.00028785	Object of calibration Uncertainty of CTE (u_aw) [K^1] 0.0000069 Reference artefact used Nominal length /mm 4 surments: 4 positions, 5 repeatitions each Position 2 12.0021 12.0021 12.0022 12.0022 12.0022 12.0022 12.0024 12.0024 12.0029 12.00291595	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 4.000100 Position 3 -12.0005 -12.0005 -12.0013 -12.0019 -12.0014 -12.001141 0.000630278 3.9725E-07 0.000352565	U _{catheration imm} 5.7735E-08 U _{catheration imm} 0.0001 Position 4 -12.0013 -12.0008 -12.0009 -12.0014 -12.0007 -12.00103642 0.000333939 1.11515E-07 0.000430245	(T _M – 20°C	$C) = (T_w - 20^{\circ}C)$ Measurements No. 1 2	Position 1 3.9991 3.999	Position 2 3.9991 3.999	3.99 3.9
Measurement [mm] 4 Type Sauge block Measurement repetition name 3-19 3-19 3-19 3-19 3-19 3-19 3-19 3-19	CTE [K-1] 2.22E-05 Part number Calibration meas Position 1 -12.0019917 -12.003918 -12.0014118 -12.001468 -12.003973 -12.0025788 0.000609541 3.71541E-07 0.000208785 4.35912E-08	Object of calibration Uncertainty of CTE (u _{vw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 4 surments: 4 positions, 5 repeatitions each Position 2 -12.0023 -12.0021 -12.0026 -12.0022 -12.0022 -12.00245826 0.000491934 2.41999E-07 -0.00991595 9.83261E-07	(u ² _{TW} + u ² _{TWS}) [K ²] 0.0033333333 Calibrated length /mm 4.000100 Position 3 -12.0005 -12.0005 -12.0013 -12.0013 -12.0014 -12.001141 0.000630278 3.9725E-07	U _{salth-sation imm} 5.7735E-08 U _{calth-sation imm} 0.0001 Position 4 -12.0013 -12.0009 -12.0014 -12.0009 -12.0013642 0.000333939 1.11518E-07	(T _M – 20°C	$C) = (T_w - 20^{\circ}C)$ Measurements No. 1 2	Position 1 3.9991 3.999	Position 2 3.9991 3.999	3.99 3.9
Length of measurement [mm] 4 Type Sauge block Measurement repetition name 3-19 3-19 3-19 3-19 3-19 3-19 3-19 3-19	0.000654595 CTE [K-1] 2.22E-05 Part number - Calibration meas Position 1 -12.001917 -12.0009418 -12.00140118 -12.0015468 -12.003973 -12.00125788 0.000609541 3.71541E-07 0.00028785	Object of calibration Uncertainty of CTE (u _{vw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 4 surments: 4 positions, 5 repeatitions each Position 2 -12.0023 -12.0021 -12.0026 -12.0022 -12.0022 -12.00245826 0.000491934 2.41999E-07 -0.00991595 9.83261E-07	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 4.000100 Position 3 -12.0005 -12.0005 -12.0013 -12.0019 -12.0014 -12.001141 0.000630278 3.9725E-07 0.000352565	U _{catheration imm} 5.7735E-08 U _{catheration imm} 0.0001 Position 4 -12.0013 -12.0008 -12.0009 -12.0014 -12.0007 -12.00103642 0.000333939 1.11515E-07 0.000430245	(T _M – 20°C	C) = (T _w - 20°C) Measurements No. 1 2 3	Position 1 3.9991 3.999 3.9991	Position 2 3.9991 3.999	3.99 3.9
Measurement [mm] 4 Type Sauge block Measurement repetition name 3-19 3-19 3-19 3-19 3-19 3-19 3-19 3-19	CTE [K-1] 2.22E-05 Part number Calibration meas Position 1 -12.0019917 -12.003918 -12.0014118 -12.001468 -12.003973 -12.0025788 0.000609541 3.71541E-07 0.000208785 4.35912E-08	Object of calibration Uncertainty of CTE (u _{vw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 4 surments: 4 positions, 5 repeatitions each Position 2 -12.0023 -12.0021 -12.0026 -12.0022 -12.0022 -12.00245826 0.000491934 2.41999E-07 -0.00991595 9.83261E-07	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 4.000100 Position 3 -12.0005 -12.0005 -12.0013 -12.0019 -12.0014 -12.001141 0.000630278 3.9725E-07 0.000352565	U _{catheration imm} 5.7735E-08 U _{catheration imm} 0.0001 Position 4 -12.0013 -12.0008 -12.0009 -12.0014 -12.0007 -12.00103642 0.000333939 1.11515E-07 0.000430245	(T _M – 20°C	$C) = (T_w - 20^{\circ}C)$ Measurements No. 1 2	Position 1 3.9991 3.999	Position 2 3.9991 3.999	3.99 3.9
Type auge block Measurement repetition name 3-19 3-19 3-19 3-19 3-19 3-19 3-19 3-1	0.000654595 CTE [K*] 2.22E-05 Part number - Calibration meas Position 1 -12.0019917 -12.0099418 -12.0015468 -12.0015468 -12.0015468 -12.0015468 -10.003973 -12.00125788 0.000609541 3.71541E-07 0.000208785 4.35912E-08	Object of calibration Uncertainty of CTE (u _{vw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 4 surments: 4 positions, 5 repeatitions each Position 2 -12.0023 -12.0021 -12.0026 -12.0022 -12.0022 -12.00245826 0.000491934 2.41999E-07 -0.00991595 9.83261E-07	(u ² _{TW} + u ² _{TWS}) [K ²] 0.003333333 Calibrated length /mm 4.000100 Position 3 -12.0005 -12.0005 -12.0013 -12.0019 -12.0014 -12.001141 0.000630278 3.9725E-07 0.000352565	U _{catheration imm} 5.7735E-08 U _{catheration imm} 0.0001 Position 4 -12.0013 -12.0008 -12.0009 -12.0014 -12.0007 -12.00103642 0.000333939 1.11515E-07 0.000430245	(T _M – 20°C	C) = (T _w - 20°C) Measurements No. 1 2 3	Position 1 3.9991 3.999 3.9991	Position 2 3.9991 3.999	3.99 3.9
Type auge block Measurement repetition name 3-19 3-19 3-19 3-19 3-19 3-19 3-19 3-1	0.000654595 CTE [K*] 2.22E-05 Part number - Calibration meas Position 1 -12.0019917 -12.0099418 -12.0015468 -12.0015468 -12.0015468 -12.0015468 -10.003973 -12.00125788 0.000609541 3.71541E-07 0.000208785 4.35912E-08	Object of calibration Uncertainty of CTE (u _{aw}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 4 surments: 4 positions, 5 repeatitions each Position 2 -12.0033 -12.0021 -12.0022 -12.0022 -12.0022 -12.0022 -10.0024 -12.0022 -10.0024 -10.0045826 0.000491934 2.41999E-07 -0.000991595 9.83261E-07	(u ² _{TW} + u ² _{TWS}) [K ²] 0.0033333333 Calibrated length /mm 4.000100 Position 3 -12.0005 -12.0005 -12.0013 -12.0013 -12.0014 -12.001141 0.000630278 3.9725E-07 0.000352565 1.24302E-07	U _{catheration imm} 5.7735E-08 U _{catheration imm} 0.0001 Position 4 -12.0013 -12.0008 -12.0009 -12.0014 -12.0007 -12.00103642 0.000333939 1.11515E-07 0.000430245	(T _M – 20°C	C) = (T _w - 20°C) Measurements No. 1 2 3	Position 1 3.9991 3.9991 3.9991 -0.000258327	Position 2 3.9991 3.999 3.9991	3.99 3.9
Type auge block Measurement repetition name 3-19 3-19 3-19 3-19 3-19 3-19 3-19 3-1	CTE [K ⁻¹] 2.22E-05 Part number - Callbration meas Position 1 -12.0019917 -12.0099418 -12.0014118 -12.0015468 -12.00125788 0.000609541 3.71541E-07 0.000208785 4.35912E-08	Object of calibration Uncertainty of CTE (u_w) [K ⁻¹] 0.0000069 Reference artefact used Nominal length /mm 4 surments: 4 positions, 5 repeatitions each Position 2 -12.0023 -12.0021 -12.0025 -12.0022 -12.0022 -12.0022 -12.0024526 0.000491934 2.41999E-07 -0.00091595 9.83261E-07		U _{catheration imm} 5.7735E-08 U _{catheration imm} 0.0001 Position 4 -12.0013 -12.0008 -12.0009 -12.0014 -12.0007 -12.00103642 0.000333939 1.11515E-07 0.000430245	(T _M – 20°C	$(T_w - 20^{\circ}C)$ $(T_w - 20^$	Position 1 3.9991 3.9991 3.9991 -0.000258327	Position 2 3.9991 3.999	3.99 3.9
Type auge block Measurement repetition name 3-19 3-19 3-19 3-19 3-19 3-19 3-19 3-1	CTE [K ⁻¹] 2 22E-05 Part number - Calibration meas Position 1 -12.0019917 -12.0099418 -12.0014118 -12.0015468 -12.00125788 0.000609541 3.71541E-07 0.000208785 4.35912E-08 95.45] % -12.00146667	Object of calibration Uncertainty of CTE (u _{ew}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 4 surments: 4 positions, 5 repeatitions each Position 2 -12.0023 -12.0021 -12.0026 -12.0022 -12.0022 -12.0022 -12.0024 9.000491934 2.41999E-07 -0.000991595 9.83281E-07		U _{catheration imm} 5.7735E-08 U _{catheration imm} 0.0001 Position 4 -12.0013 -12.0008 -12.0009 -12.0014 -12.0007 -12.00103642 0.000333939 1.11515E-07 0.000430245	(T _M – 20°C	C) = (T _w - 20°C) Measurements No. 1 2 3 E _{Lprop} L _{measstd}	Position 1 3.9991 3.9991 3.9991 3.9991 3.9991 3.999066667	Position 2 3.9991 3.999 3.9991	3.99 3.9
Type Sauge block Measurement repetition name 3-19 3-19 3-19 3-19 3-19 3-19 3-19 3-19	CTE [K ⁻¹] 2 22E-05 Part number - Calibration meas Position 1 -12.0019917 -12.0099418 -12.0014118 -12.0015468 -12.00125788 0.000609541 3.71541E-07 0.000208785 4.35912E-08 95.45] % -12.00146667	Object of calibration Uncertainty of CTE (u _{ew}) [K ⁻¹] 0.00000069 Reference artefact used Nominal length /mm 4 surments: 4 positions, 5 repeatitions each Position 2 -12.0023 -12.0021 -12.0026 -12.0022 -12.0022 -12.0022 -12.0024 9.000491934 2.41999E-07 -0.000991595 9.83281E-07		U _{catheration imm} 5.7735E-08 U _{catheration imm} 0.0001 Position 4 -12.0013 -12.0008 -12.0009 -12.0014 -12.0007 -12.00103642 0.000333939 1.11515E-07 0.000430245	(T _M – 20°C	C) = (T _w - 20°C) Measurements No. 1 2 3 E _{Lprop} L _{measstd}	Position 1 3.9991 3.9991 3.9991 3.9991 3.9991 3.999066667	Position 2 3.9991 3.999 3.9991	3.99 3.9

Effective degree of freedom

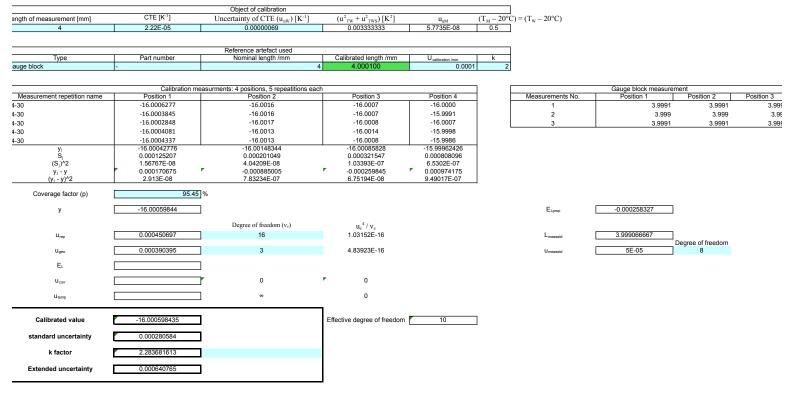
		Object of calibration							
Length of measurement [mm]	CTE [K-1]	Uncertainty of CTE (uaw) [K-1]	$(u_{TW}^2 + u_{TWS}^2) [K^2]$	$u_{\alpha M}$	$(T_M - 20^\circ)$	$^{\circ}$ C) = (T _W – 20 $^{\circ}$ C)			
4	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5				
		Reference artefact used				7			
Type	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	l k	1			
Gauge block	-	4		0.0001	1 2	2			
	•		•		'	_			
	O-liberties es				7		O blask		
Measurement repetition name	Position 1	easurments: 4 positions, 5 repeatitions each Position 2	Position 3	Position 4	-	Measurements No.	Gauge block measurer Position 1	Position 2	Position 3
19-25	-12.0005093	-12.0013	-12.0007	-12.0006	1	1	3.9991	3,9991	3,999
19-25	-12.001008	-12.0013	-12.0007	-11.9985		2	3.999	3.999	3.999
19-25	-12.0004875	-12.0011	-12.0011	-11.9998		3	3.9991	3.9991	3.9991
19-25	-12.0007119	-12.0014	-12.0005	-11.9989		-			
19-25	-12.0001984	-12.0012	-12.0008	-11.9992					
	-12.00058302	-12.0012525	-12.00076532	-11.99940198	1				
y _j S _j	0.000299879	0.00011452	0.00022087	0.000803054					
(S _J)^2	8.99273E-08	1.31148E-08	4.87837E-08	6.44895E-07					
y _j - y (y _i - y)^2	-8.2315E-05 6.77576E-09	-0.000751795 5.65196E-07	-0.000264615 7.00211E-08	0.001098725 1.2072E-06					
(y _j - y) ² /2	6.77576E-09	5.65196E-07	7.00211E-08	1.20/2E-06					
Coverage factor (p)	95.45]%							
v	-12.00050071	1				E _{Lprop}	-0.000258327		
у	-12.00090071	1				⊏Lprop	-0.000258327		
		Degree of freedom (v _c)	u_e^4/v_e						
Urep	0.000446296	16	9.91819E-17			L _{measstd}	3.999066667		
-145		-				- included		Degree of freedom	
u _{geo}	0.000392555] 3	4.94719E-16			U _{measstd}	5E-05	8	
E∟		1							
		1							
U _{corr}		0	0						
U _{temp}] ∞	0						
		-	_						
		1	1		_				
Calibrated value	-12.000500705	1	Effective degree of freedom	10					
standard uncertainty	0.00027993	1							
k factor	2.283681613								
Extended uncertainty	0.000639271	1							
Extended uncertainty	0.000035211	1							
			4						



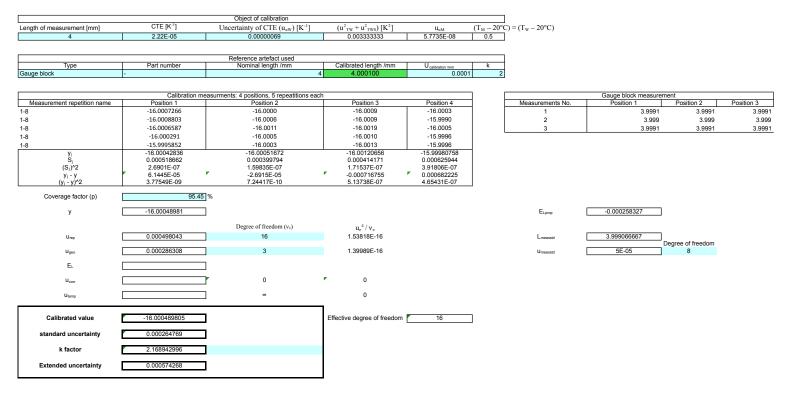
		Object of calibration				1			
Length of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{oW}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	$u_{\alpha M}$	(T – 20°	$(C) = (T_w - 20^{\circ}C)$			
4	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5	1			
	2.222 00	0.0000000	0.00000000	0.17002 00	0.0	ı			
Type	Part number	Reference artefact used Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	l k				
Gauge block	- Part Humber		4.000100	0.0001					
Gauge block	-		4.000100	0.0001	-	1			
					_				
		asurments: 4 positions, 5 repeatitions each					Gauge block measure		
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	4	Measurements No.	Position 1	Position 2	Position 3
6-12	-12.0003435 -12.0005833	-11.9992 -12.0012	-12.0000 -12.0000	-11.9983 -11.9984		1	3.9991	3.9991	3.9991
6-12	-12.0005833	-12.0012 -12.0026	-12.0000	-11.9984		2 3	3.999	3.999	3.999
6-12	-12.0005768	-12.0026	-12.0006	-11.9988		3	3.9991	3.9991	3.9991
6-12 6-12	-12.0006669	-12.0004	-12.0004	-11.9984					
	-12.00071736	-12.0003	-12.0003	-11.99857614	+				
y _i S _i	0.000408829	0.001239058	0.000299641	0.000277142					
(S _j)^2	1.67141E-07	1.53526E-06	8.9785E-08	7.68078E-08					
y ₁ - y		-0.000667865		0.001498635					
(y ₁ - y)^2	4.12915E-07	4.46044E-07	3.54136E-08	2.24591E-06	_				
Coverage factor (p)	95.45	%							
y	-12.00007478					E _{Lprop}	-0.000258327		
		Degree of freedom (v _e)	u_e^4/v_e						
	0.000683557	16	u _e / v _e 5.45805E-16			1	3.999066667		
U _{rep}		10	3.43003E-10			L _{measstd}		Degree of freedom	
u_{geo}	0.000511556	3	1.4267E-15			U _{measstd}	5E-05	8	
EL									
U _{corr}		0	0						
U _{temp}		∞	0						
- varip			-						
Calibrated value	-12.000074775		Effective degree of freedom	12]				
standard uncertainty	0.000398588	1							
k factor	2.231351317								
Extended uncertainty	0.00088939								
H-									

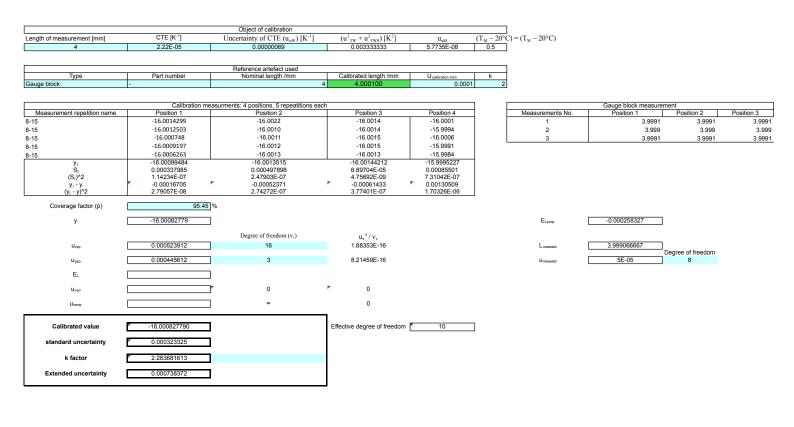


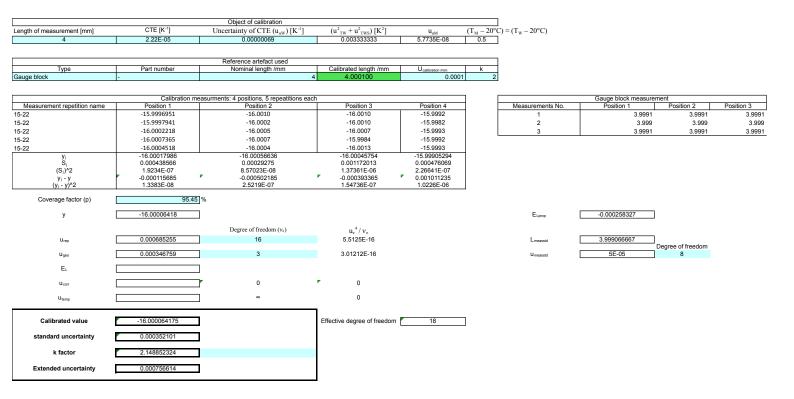
		Object of calibration				1			
Length of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{aW}) [K ⁻¹]	$(u_{TW}^2 + u_{TWS}^2) [K^2]$	u_{aM}	(T _M - 20°	$C) = (T_W - 20^{\circ}C)$			
4	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5	1´ ` ¨ ´			
	•		•		-	•			
		Reference artefact used				1			
Type	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	l k	1			
Gauge block	-	4		0.000					
	•		-			-			
	Calibration	easurments: 4 positions, 5 repeatitions eac	h		_		Course block measures	ant	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	4	Measurements No.	Gauge block measuren Position 1	Position 2	Position 3
18-24	-12.0017589	-12.0026	-12.0017	-12.0017	1	1	3.9991	3.9991	3.999
18-24	-12.0017457	-12.0016	-12.0017	-12.0019		2	3.999	3.999	3.99
18-24	-12.0017274	-12.0014	-12.0006	-12.0018		3	3,9991	3.9991	3.999
18-24	-12.0002517	-12.0026	-12.0022	-11.9997			0.5551	0.0001	0.000
18-24	-11.9999413	-12.0025	-12.0016	-11.9999					
	-12.001085	-12.00214976	-12.00154236	-12.00098956					
y _j S _i	0.00090909	0.000614533	0.000606035	0.001092781					
(S _j)^2	8.26446E-07	3.77651E-07	3.67278E-07	1.19417E-06					
y _i - y	0.00000001	-0.00070809	-0.00010003	0.00045211					
(y _j - y)^2	1.27213E-07	5.01391E-07	1.01385E-08	2.04403E-07					
Coverage factor (p)	95.45	1%							
(,,									
у	-12.00144167	1				E _{Lprop}	-0.000258327		
		Degree of freedom (ve)	u_e^4/v_e						
	0.000831496	16	1.19504E-15			1	3.999066667		
U _{rep}	0.000631490	10	1.19304E-13			L _{measstd}		Degree of freedom	
u _{geo}	0.00026507	3	1.0285E-16			U _{measstd}	5E-05	8	
-									
EL]							
Ucorr		P 0	0						
- 5001		-							
U _{temp}		_ ∞	0						
		_	1		_				
Calibrated value	-12.001441670		Effective degree of freedom	18					
standard uncertainty	0.000394769	1							
Standard uncertainty	0.000394769	1							
k factor	2.148852324								
Extended uncertainty	0.000848301	1							
Extended uncertainty	0.000040301	ı							
L			1						

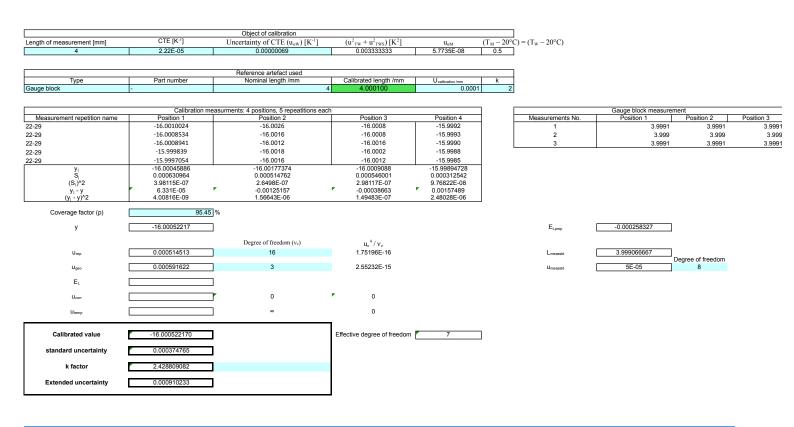


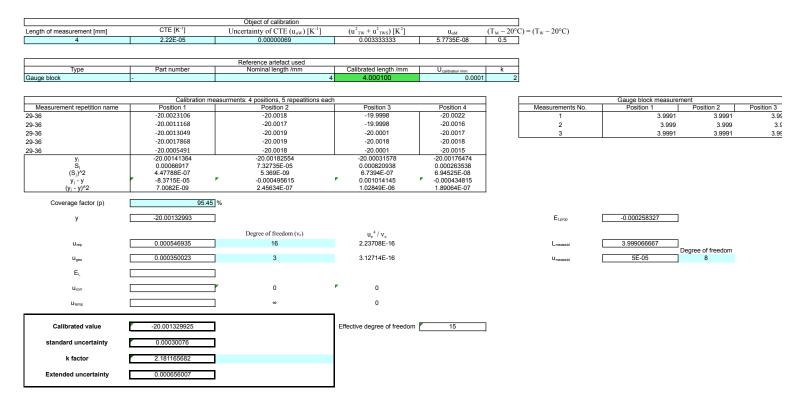
		Object of calibration							
Length of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{aW}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS})[K^2]$	$u_{\alpha M}$	(T _M - 20°	$(C) = (T_w - 20^{\circ}C)$			
4	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5	l´ ` "			
		Reference artefact used							
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
Gauge block	-	4	4.000100	0.0001	2				
	Calibration me	asurments: 4 positions, 5 repeatitions each	h		1		Gauge block measuren	nent	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	†	Measurements No.	Position 1	Position 2	Position 3
30-36	-16.0007557	-16.0020	-15.9997	-16.0009	1	1	3.9991	3.9991	3.999
30-36	-16.0001118	-16.0010	-15.9997	-16.0007		2	3.999	3.999	3.999
30-36	-15.999499	-16.0014	-16.0006	-16.0011		3	3.9991	3.9991	3.999
30-36	-15.9998659	-16.0014	-15.9993	-16.0009		-			
30-36	-16.0005498	-16.0014	-16.0006	-16.0006					
	-16.00015644	-16.0014493	-15.99998518	-16.00082158	1				
y _i S _j	0.000508055	0.000345469	0.000571957	0.00018308					
(S _j)^2	2.5812E-07	1.19349E-07	3.27135E-07	3.35181E-08					
y _i - y	0.000446685			-0.000218455					
(y _j - y)^2	1.99527E-07	7.16012E-07	3.81856E-07	4.77226E-08]				
	05.45	24							
Coverage factor (p)	95.45	%							
у	-16.00060313					E _{Lprop}	-0.000258327		
y	-10.00000010					∟ Lprop	-0.000230327		
		Degree of freedom (v _e)	u_e^4 / v_e						
U_{rep}	0.00042957	16	8.51287E-17			L _{meassid}	3.999066667		
Urep .	0.00042337	10	0.012072-17			□ measstd		Degree of freedom	
U _{geo}	0.000334803	3	2.61768E-16			U _{measstd}	5E-05	8	
9									
EL									
			• 0						
U _{corr}		0	0						
		∞	0						
U _{temp}			Ü						
			1						
Calibrated value	-16.000603125		Effective degree of freedom	12	1				
				·-	1				
standard uncertainty	0.000254812								
·									
k factor	2.231351317								
	,								
Extended uncertainty	0.000568576								
		-							



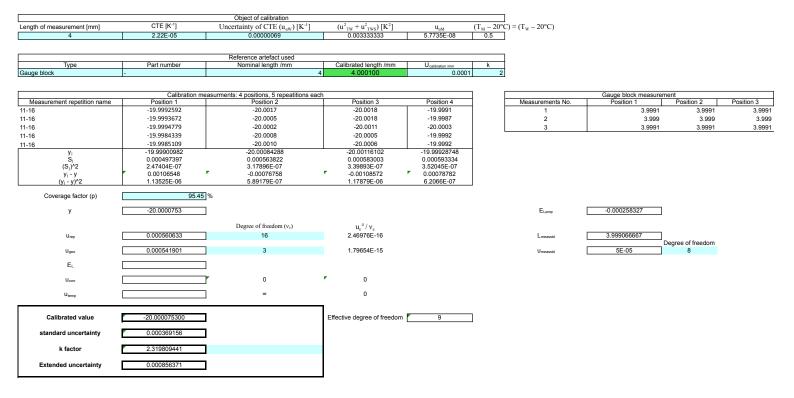




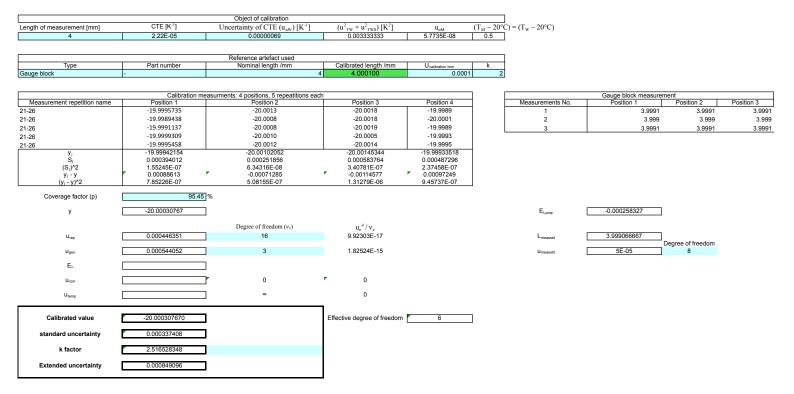


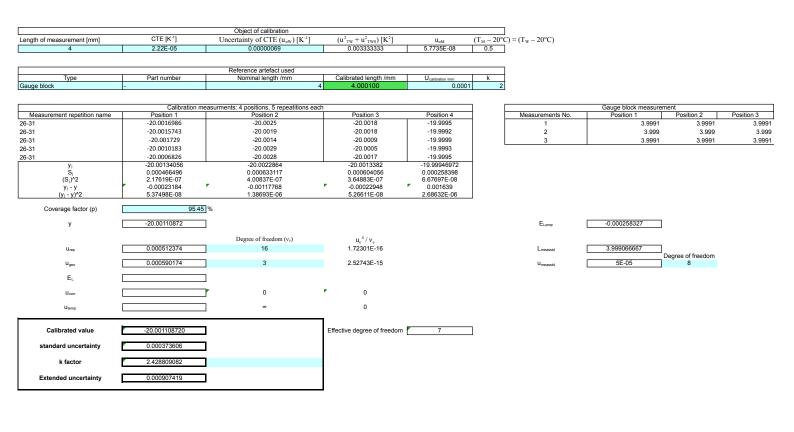


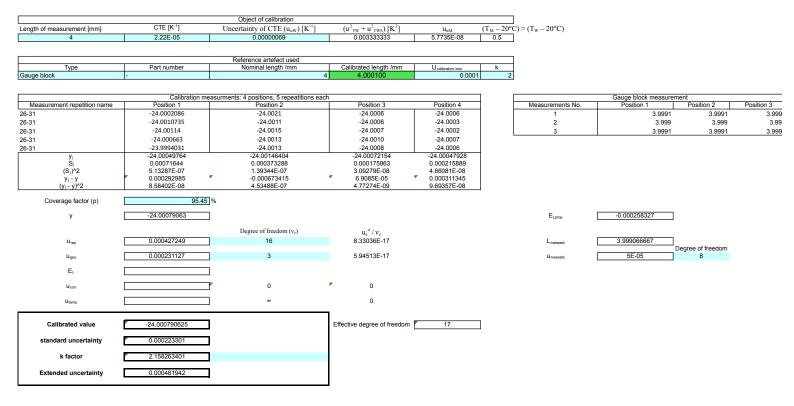
		Object of calibration							
igth of measurement [mm]	CTE [K-1]	Uncertainty of CTE (uaw) [K-1]	$(u^2_{TW} + u^2_{TWS})[K^2]$		$(T_M - 20^{\circ}C)$	$= (T_W - 20^{\circ}C)$			
4	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5				
		Reference artefact used							
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
uge block -		4	4.000100	0.0001	2				
		asurments: 4 positions, 5 repeatitions each] [Gauge block measuren		
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	↓ ⊢	Measurements No.	Position 1	Position 2	Position 3
1	-20.0011524	-20.0007	-20.0011	-19.9995		1	3.9991	3.9991	3.999
1	-20.0013846	-20.0020	-20.0011	-19.9990		2	3.999	3.999	3.99
1	-20.0010938	-20.0016	-20.0011	-19.9998		3	3.9991	3.9991	3.999
1	-20.0015344	-20.0014	-20.0010	-19.9995					
1	-20.0018005	-20.0012	-20.0010	-19.9992	4				
y _i S _i	-20.00139314 0.00028876	-20.00136398 0.000476082	-20.00105106 7.33914E-05	-19.99940004 0.000300196					
(S _i)^2	8.33824E-08	2.26654E-07	5.3863E-09	9.01179E-08					
y ₁ - y	-0.000591085	-0.000561925		0.001402015					
(y ₁ - y)^2	3.49381E-07	3.1576E-07	6.20035E-08	1.96565E-06					
Coverage factor (p)	95.45	%							
у	-20.00080206					E _{Lprop}	-0.000258327		
		Degree of freedom (v _c)	$u_{\rm c}^4/v_{\rm c}$						
U _{rep}	0.00031841	16	2.56974E-17			L _{measstd}	3.999066667		
U rep	0.00001041	10	2.505742-17			∟ meassio		Degree of freedom	
Ugeo	0.000473708	3	1.04906E-15			U _{measstd}	5E-05	8	
E _L									
_			_						
Ucorr		0	0						
U _{temp}		∞	0						
Calibrated value	-20.000802055		Effective degree of freedom	5	1				
_					1				
standard uncertainty	0.000276364								
k factor	2.648654254								
Extended uncertainty	0.000731992								
	5.5557.5153E		I						



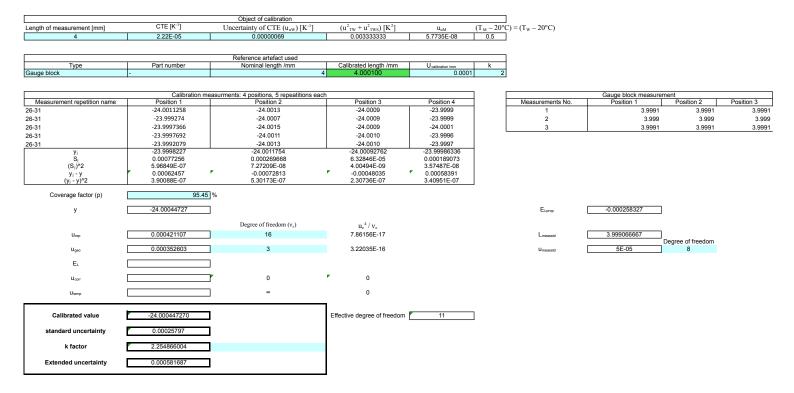
Length of measurement [mm]			Object of calibration				1		
Reference artificial tused Calibration reason Regimence artificial tused Regimence artificial tused Calibration reason Regimence artificial tused Calibration reason Regimence artificial tused Calibration reason Regimence artificial tused Calibration reason Regimence R	Length of measurement [mm]	CTE [K-1]		$(u^2_{TW} + u^2_{TWS}) [K^2]$	$u_{\sigma M}$	(T _M – 20°0	$(T_w - 20^{\circ}C)$		
Type Part number Norminal length frim Calibrated relays from Userserium K 4 000100 0.0001 2 Calibration neasurments 4 position 3		2.22E-05					1		
Type Part number Norminal length frim Calibrated relays from Userserium K 4 000100 0.0001 2 Calibration neasurments 4 position 3				'			•		
Type Part number Norminal length frim Calibrated relays from Userserium K 4 000100 0.0001 2 Calibration neasurments 4 position 3			Reference artefact used				1		
Measurement repetition massurements	Туре	Part number		Calibrated length /mm	U _{calibration /mm}	k			
Measurement repetition name	Gauge block	-	4	4.000100	0.000	1 2			
Measurement repetition name									
16-21		Calibration me		1		7			
16-21						1	Measurements No.		
16-21	16-21						1	3.9991 3.9991	3.9991
16-21									3.999
16-21							3	3.9991 3.9991	3.9991
y -20.00028988	16-21								
S, 0.000240534 0.00029993 0.00017487 (S), 22 5.78568E-08 8.899957E-08 3.64311E-08 6.68288E-07						╛			
(S)/Y2	y _i								
V _j - y	S _i								
Coverage factor (p) 95.45									
Coverage factor (p) 95.45 % y -20.00054992 Degree of freedom (v _c) U _{rep} 0.000461673 16 1.13574E-16 U _{geo} 0.000287167 3 1.41676E-16 Et U _{tour} 0 0 0 0 0 U _{tour} 0 0 0 0 Calibrated value -20.000549915 standard uncertainty 0.000251485 Effective degree of freedom 15	(v _i - v)^2								
y		•				_			
Degree of freedom (v _c) U _{sp} 0.000461673 16 1.13574E-16 L _{measted} 3.999066667 Degree of freedom U _{sp} 0.000287167 3 1.41676E-16 U _{measted} 5E-05 8	Coverage factor (p)	95.45	%						
Ump 0.000461673 16 1.13574E-16 Lmeasted 3.99906667 Uges 0.000287167 3 1.41676E-16 Umeasted 5E-05 B EL Umeasted 5E-05 8 Umany 0 0 0 Calibrated value -20.000549915 -20.000549915 Effective degree of freedom 15 k factor 2.181165682 Effective degree of freedom 15	у	-20.00054992					E _{Lprop}	-0.000258327	
Usep 0.000461673 16 1.13574E-16 Lmeasstd 3.99906667 Ugeo 0.000287167 3 1.41676E-16 Umeasstd 5E-05 Degree of freedom Et. 0 0 0 User 0 0 Calibrated value -20.000549915 Effective degree of freedom 15 k factor 2.181165682			Degree of freedom (v _c)	u 4 / v					
U _{gro} 0.000287167 3 1.41676E-16 U _{meassed} 5E-05 8 E _L U _{corr} 0 0 U _{tomp} ∞ 0 Calibrated value -20.000549915 Effective degree of freedom 15 standard uncertainty 0.000251485 Effective degree of freedom 15	U _{rep}	0.000461673	16				L _{measstd}		
EL		0.000007467	2	1 416765 16				Degree of freedom	
U _{temp} ∞ 0 Calibrated value -20.000549915 Effective degree of freedom standard uncertainty 0.000251485 k factor 2.181165682	u _{geo}	0.000267167	3	1.410/00-10			U _{measstd}	3E-03 0	
U _{temp}	EL								
Calibrated value -20.000549915 Effective degree of freedom 15 standard uncertainty 0.000251485 Effective degree of freedom 15	Urorr		r 0	• 0					
Calibrated value -20.000549915 Effective degree of freedom 15 standard uncertainty 0.000251485 15 k factor 2.181165682 15									
standard uncertainty	U _{temp}		∞	0					
standard uncertainty	Calibrated value	20.000540045		Effective degree of freedom	15	7			
k factor 2.181165682	Calibrated value	-20.000549915		Ellective degree of freedom	15	_			
	standard uncertainty	0.000251485							
	k factor	2 181165682							
Extended uncertainty 0.00054853	K Ideloi	2.101103002							
	Extended uncertainty	0.00054853							







		Object of calibration							
Length of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{ow}) [K ⁻¹]	$(u_{TW}^2 + u_{TWS}^2) [K^2]$	$u_{\alpha M}$	(T ₁₁ – 20°C	$T = (T_w - 20^{\circ}C)$			
4	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5	, (w ·)			
	•		•	•					
		Reference artefact used							
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
Gauge block	-	4	4.000100	0.000	1 2				
	Calibration me	asurments: 4 positions, 5 repeatitions each	1		7 .		Gauge block measureme	nt	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4] [Measurements No.	Position 1	Position 2	Position 3
26-31	-24.0012783	-24.0024	-24.0010	-24.0010		1	3.9991	3.9991	3.9991
26-31	-24.001595	-24.0019	-24.0010	-24.0011		2	3.999	3.999	3.999
26-31	-24.0016059	-24.0015	-24.0010	-24.0012		3	3.9991	3.9991	3.9991
26-31	-24.0013509	-24.0016	-24.0008	-24.0012					
26-31	-24.0003128 -24.00122858	-24.0017 -24.00181524	-24.0011 -24.00096024	-24.0012 -24.0011558	4				
y _i S _i	0.000532147	0.000351959	0.00012099	-24.0011558 8.45081E-05					
(S ₁)^2	2.8318E-07	1.23875E-07	1.46386E-08	7.14163E-09					
y _i - y	6.1385E-05	-0.000525275	0.000329725	0.000134165					
(y _i - y)^2	3.76812E-09	2.75914E-07	1.08719E-07	1.80002E-08					
Coverage factor (p)	95.45	%							
у	-24.00128997					E _{Lprop}	-0.000258327		
		Degree of freedom (ve)	u_e^4/v_e						
u _{rep}	0.000327428	16	2.87344E-17			L _{measstd}	3.999066667		
U _{geo}	0.000184029	3	2.38949E-17			U _{measstd}	5E-05	egree of freedom 8	
E _L									
LL.		l e e e e e e e e e e e e e e e e e e e							
Ucorr		0	0						
U _{temp}		∞	0						
			1		_				
Calibrated value	-24.001289965		Effective degree of freedom	16					
standard uncertainty	0.000172941								
k factor	2.168942996								
Extended uncertainty	0.000375098								
			I						



		Object of calibration]			
Length of measurement [mm]	CTE [K-1]	Uncertainty of CTE (uaW) [K-1]	$(u^2_{TW} + u^2_{TWS})[K^2]$	$u_{\alpha M}$	$(T_{\rm M} - 20^{\circ})$	$(C) = (T_w - 20^{\circ}C)$			
4	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5				
		Reference artefact used				1			
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
Gauge block	-	4	4.000100	0.0001	2				
	Calibration me	easurments: 4 positions, 5 repeatitions each	h		1		Gauge block measurer	ment	-
Measurement repetition name	Position 1	Position 2	Position 3	Position 4		Measurements No.	Position 1	Position 2	Position 3
26-31	-24.0003851	-24.0010	-24.0012	-23.9982	1	1	3.9991	3.9991	3.9
26-31	-24.0000509	-24.0008	-24.0012	-23.9987		2	3.999	3.999	3.9
26-31	-23.9997132	-24.0009	-24.0004	-23.9993		3	3.9991	3.9991	3.9
26-31	-24.0001334	-24.0007	-24.0003	-23.9982					
26-31	-23.999614	-24.0009	-24.0004	-23.9987					
y _i	-23.99997932	-24.00085188	-24.00070458	-23.9986309	1				
y _i S _i	0.000315357	0.000136355	0.000473255	0.000473309					
(S _j)^2	9.94501E-08	1.85927E-08	2.2397E-07	2.24022E-07					
y _j - y	0.200L-00	-0.00081021 6.5644E-07	-0.00066291 4.3945E-07	0.00141077 1.99027E-06					
(y _j - y)^2	3.88752E-09	6.5644E-07	4.3945E-07	1.99027E-06	_				
Coverage factor (p)	95.45	%							
у	-24.00004167	1				E _{Lprop}	-0.000258327		
y	-24.00004107					Lprop	-0.000236327		
		Degree of freedom (v _c)	u_e^4/v_e						
U _{rep}	0.000376176	16	5.00618E-17			L _{measstd}	3.999066667		
								Degree of freedom	
U _{geo}	0.000507449	3	1.38142E-15			U _{measstd}	5E-05	8	
-		ı							
E∟									
U _{corr}		0	0						
U _{temp}		∞	0						
			1						
Calibrated value	-24.000041670	1	Effective degree of freedom	6	7				
					_				
standard uncertainty	0.00030443								
k factor	2.516528348								
1	0.000700407								
Extended uncertainty	0.000766107								
			1						

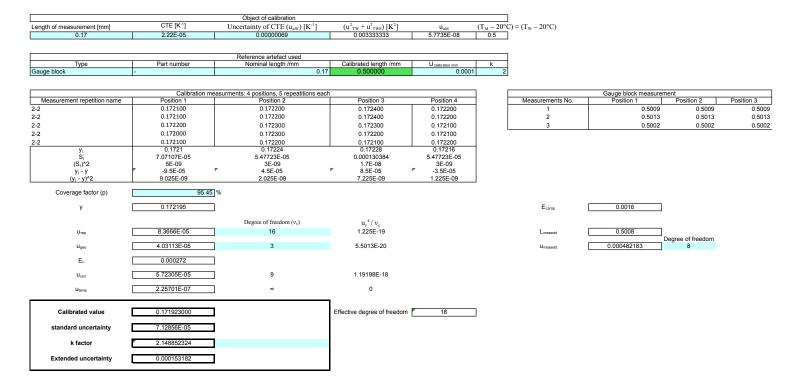
		Object of calibration							
Length of measurement [mm]	CTE [K-1]	Uncertainty of CTE (uaW) [K-1]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	$u_{\alpha M}$	$(T_M - 20^\circ$	$C) = (T_W - 20^{\circ}C)$			
4	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5				
		Reference artefact used				1			
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
Gauge block	-	4		0.0001	2				
						•			
	Calibratian ma	asurments: 4 positions, 5 repeatitions each	h		1		Gauge block measurem	ant.	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4		Measurements No.	Position 1	Position 2	Position 3
26-31	-24.0007855	-24.0005	-24.0014	-24.0008		1	3.9991	3.9991	3.9991
26-31	-24.0002997	-24.0008	-24.0014	-23.9995		2	3.999	3.999	3.999
26-31	-24.0013551	-24.0022	-24.0016	-24.0014		3	3.9991	3.9991	3.9991
26-31	-24.0001242	-24.0001	-24.0012	-23.9981		1	•		
26-31	-23.99963	-24.0003	-24.0011	-23.9977					
y _i S _i	-24.0004389	-24.00076432	-24.00133486	-23.99951392					
	0.000658082	0.000822005	0.000173979	0.001611597					
(S _j)^2 y _j - y	4.33071E-07 7.41E-05	6.75692E-07 -0.00025132	3.02689E-08 -0.00082186	2.59725E-06 0.00099908					
(y _i - y)^2	5.49081E-09	6.31617E-08	6.75454E-07	9.98161E-07					
	•				•				
Coverage factor (p)	95.45	%							
У	-24.000513	1				E _{Lprop}	-0.000258327		
,						-грор			
		Degree of freedom (v _e)	u_e^4/v_e						
U _{rep}	0.000966473	16	2.18121E-15			L _{measstd}	3.999066667		
	0.000001007		4.004005.40					Degree of freedom	
U _{geo}	0.000381037	3	4.39163E-16			U _{measstd}	5E-05	8	
E∟									
Ucorr		0	0						
U _{temp}		œ	0						
Otemp			Ü						
			1						
Calibrated value	-24.000513000		Effective degree of freedom	18					
standard uncertainty	0.000472346	Ì							
standard uncertainty	0.000472340								
k factor	2.148852324								
Extended uncertainty	0.001015003								
			1						
			_						

Extended uncertainty

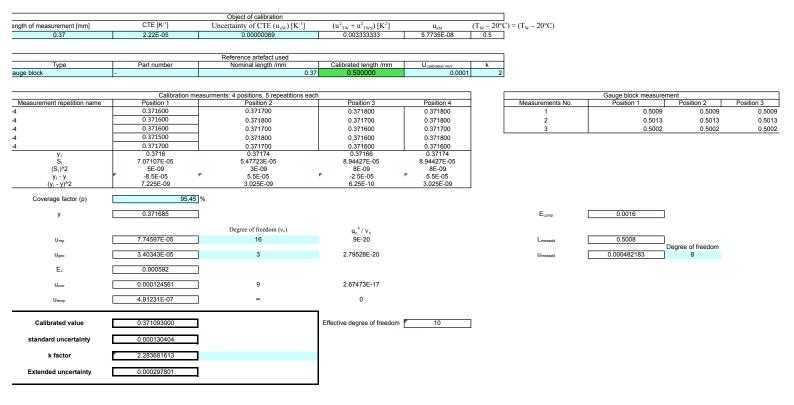
		Object of calibration							
Length of measurement [mm]	CTE [K-1]	Uncertainty of CTE (uaW) [K-1]	$(u_{TW}^2 + u_{TWS}^2) [K^2]$	$u_{\alpha M}$	$(T_{\rm M} - 20^{\circ})$	$(C) = (T_W - 20^{\circ}C)$			
4	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5				
		Reference artefact used							
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
Gauge block	-		4.000100	0.0001	2				
	Calibration mea	asurments: 4 positions, 5 repeatitions each	h		1		Gauge block measureme	ent	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	1	Measurements No.	Position 1	Position 2	Position 3
26-31	-24.0017408	-24.0027	-24.0022	-24.0008		1	3.9991	3.9991	3.9991
26-31	-24.0022379	-24.0013	-24.0022	-23.9999		2	3.999	3.999	3.999
26-31	-24.0019566	-24.0017	-24.0005	-24.0011		3	3.9991	3.9991	3.9991
26-31	-24.0001407	-24.0020	-24.0016	-23.9992					
26-31	-23.998886	-24.0023	-24.0005	-23.9995					
y _i	-24.0009924	-24.00200538	-24.00140202	-24.00009704	1				
Si	0.001432076	0.000527103	0.000850285	0.000821909					
(S ₁)^2	2.05084E-06 0.00013181	2.77838E-07 -0.00088117	7.22985E-07 -0.00027781	6.75534E-07 0.00102717					
y _i - y (y _i - y)^2	1.73739E-08	7.76461E-07	7.71784E-08	1.05508E-06					
(y _j - y) 2	1.73739E-00	7.70401E-07	7.71764E-00	1.03300L=00	J				
Coverage factor (p)	95.45	%							
y	-24.00112421					E _{Lprop}	-0.000258327		
,						4.4			
		Degree of freedom (ve)	u_e^4 / v_e						
U _{rep}	0.000965298	16	2.17063E-15			L _{measstd}	3.999066667		
			E 00700E 40					egree of freedom	
U _{geo}	0.000400634	3	5.36723E-16			U _{measstd}	5E-05	8	
E∟									
		0	• 0						
Ucorr		0	, 0						
U _{temp}		00	0						
Calibrated value	-24.001124210		Effective degree of freedom	18	1				
					_				
standard uncertainty	0.000475906								
k footos	2.140052224								

Appendix (9) CALCULATION OF LENGTH CALIBRATION

		Object of calibration				1			
ength of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{aW}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	$u_{\alpha M}$	(T – 20°	$C = (T_w - 20^{\circ}C)$			
0.07	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5	1			
	!					•			
		Reference artefact used				1			
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
auge block	-	0.07	0.500000	0.000	1 2				
	Oalthardian man				_		0		
Measurement repetition name	Position 1	asurments: 4 positions, 5 repeatitions each Position 2	Position 3	Position 4	-	Measurements No.	Gauge block measurer Position 1	Position 2	Position 3
1	0.070100	0.070500	0.070800	0.070300	1	1	0.5009	0.5009	0.50
1	0.070200	0.070600	0.070600	0.070200		2	0.5013	0.5013	0.50
1	0.070100	0.070500	0.070400	0.070100		3	0.5002	0.5002	0.50
1	0.070200	0.070500	0.070500	0.070200		<u>_</u>	0.0002	0.0002	0.00
1	0.070200	0.070500	0.070400	0.070200					
	0.07016	0.07052	0.07054	0.0702	1				
y _i S _i	5.47723E-05	4.47214E-05	0.000167332	7.07107E-05					
(S _j)^2	3E-09	2E-09	2.8E-08	5E-09					
y, - y	0.000100	0.000103	0.000100	-0.000155					
(y _j - y)^2	3.8025E-08	2.7225E-08	3.4225E-08	2.4025E-08					
Coverage factor (p)	95.45	%							
у	0.070355					E _{Lprop}	0.0016		
		Degree of freedom (ve)	u_e^4/ν_e						
U _{rep}	9.74679E-05	16	2.25625E-19			L _{measstd}	0.5008	Degree of freedom	
u_{geo}	0.000101448	3	2.20663E-18			U _{measstd}	0.000482183	8	
EL	0.000112								
Ucorr	2.35655E-05	9	3.42661E-20						
Utemp	9.29356E-08	∞	0						
Calibrated value	0.070243000		Effective degree of freedom	10					
standard uncertainty	7.09102E-05								
k factor	2.283681613								
Extended uncertainty	0.000161936								



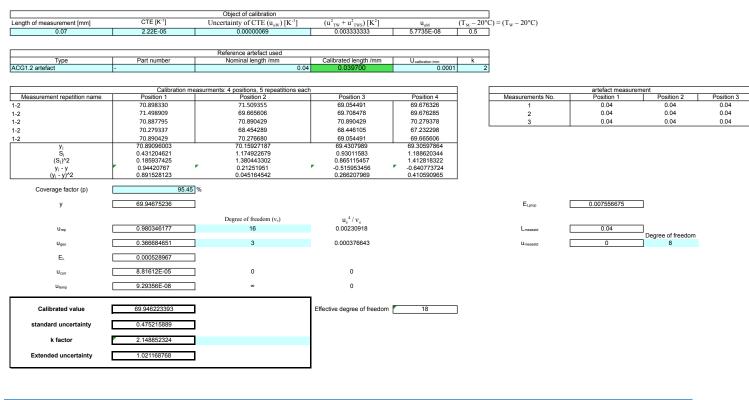
		Object of calibration				1			
Length of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{oW}) [K ⁻¹]	$(u_{TW}^2 + u_{TWS}^2) [K^2]$	u_{aM}	(T _v - 20°	$C) = (T_w - 20^{\circ}C)$			
0.27	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5	1 "			
						•			
						1			
Туре	Part number	Reference artefact used Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	l k				
Gauge block	- Fait fluitibet	0.27		0.0001					
Caago blook		0.21	0.00000	0.0001	_	1			
					_				
Management		asurments: 4 positions, 5 repeatitions each		DW 4	-	Management Na	Gauge block measurem		Diti 0
Measurement repetition name	Position 1 0.272300	Position 2	Position 3	Position 4	-	Measurements No.	Position 1	Position 2	Position 3
3-3	0.272300	0.272500	0.272400	0.272300		1	0.5009	0.5009	0.5009
3-3 3-3	0.272100	0.272500 0.272500	0.272300 0.272200	0.272300 0.272200		2 3	0.5013 0.5002	0.5013 0.5002	0.5013 0.5002
3-3	0.272100	0.272300	0.272200	0.272200		٥	0.5002	0.5002	0.5002
3-3	0.272300	0.272500	0.272200	0.272300					
	0.27218	0.27246	0.27226	0.27226	-				
y _i S _i	0.000109545	8.94427E-05	8.94427E-05	5.47723E-05					
(S _j)^2	1.2E-08	8E-09	8E-09	3E-09					
y _i - y (y _i - y)^2	-0.00011	0.00017	"JL"UJ	-3E-05					
(y _j - y)^2	1.21E-08	2.89E-08	9E-10	9E-10					
Coverage factor (p)	95.45	%							
3, 1, 1, 1, 1, 1, 1, 1, 1, 1, 1, 1, 1, 1,									
у	0.27229					E _{Lprop}	0.0016		
		Degree of freedom (v _e)	4 /						
	0.000145.05	-	u_e^4/v_e				0.5000		
U _{rep}	8.80341E-05	16	1.50156E-19			L _{measstd}	0.5008	Degree of freedom	
Ugeo	5.97216E-05	3	2.65023E-19			U _{measstd}	0.000482183	8	
EL	0.000432								
Ucorr	9.08955E-05	9	7.58452E-18						
	3.58466E-07	00	0						
U _{temp}	3.58400E-U/	∞	U						
			Ī.		_				
Calibrated value	0.271858000		Effective degree of freedom	14					
standard uncertainty	0.000103459								
k factor	2.195291287								
Extended uncertainty	0.000227123								
·			=						

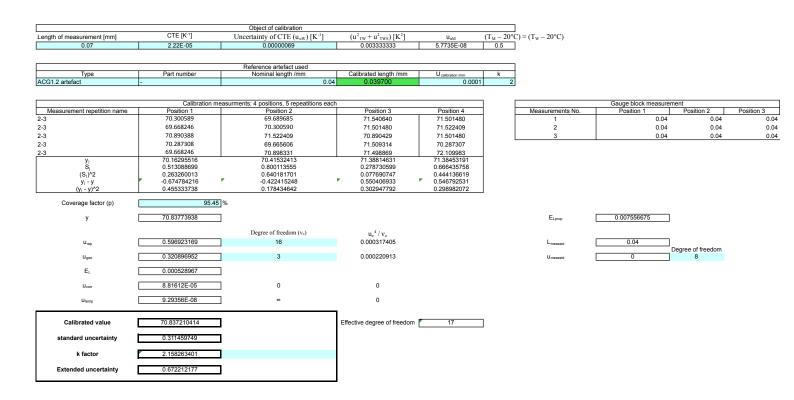


Tempto of measurement [rem]			Object of calibration				1			
Reference artificat used Normal length from Usergement K	Length of measurement [mm]	CTE [K-1]	Uncertainty of CTE (uaw) [K-1]	$(u^2_{TW} + u^2_{TWS})[K^2]$	$u_{\alpha M}$	(T _M - 20°	$C = (T_w - 20^{\circ}C)$			
Type	0.47	2.22E-05	0.00000069	0.003333333		0.5]			
Type							=			
Calibrated value 0.47 0.500900 0.0001 2			Reference artefact used				1			
Calibration measurements: 4 positions, 5 repeatitions each Position 3 Position 4	Type	Part number		Calibrated length /mm	U _{calibration /mm}	k	1			
Measurement repetition name	Gauge block	-	0.47	0.500000	0.000)1 2	1			
Measurement repetition name										
Measurement repetition name		Calibration me	easurments: 4 nositions 5 reneatitions each	h		_		Gauge block measuren	nent	
5-5	Measurement repetition name				Position 4	\dashv	Measurements No.			Position
5-5	5-5	0.471600	0.471700	0.471900	0.471900		1	0.5009	0.5009	
5-5	5-5	0.471600	0.471700	0.471900	0.471900		2	0.5013	0.5013	(
S-5	5-5	0.471600	0.471800	0.471800	0.471600		3	0.5002	0.5002	(
yi 0.47162 0.47172 0.47184 0.47184 S, 4.47214E-05 4.47214E-05 5.47723E-05 0.00012274 (S) 72 2E-09 2E-09 3E-09 1.5E-08 Y) - Y -0.000125 2.5E-05 7 9.5E-05 7 5.5E-05 (Y ₁ - Y) ² 1.5625E-08 6.25E-10 9.025E-09 3.025E-09 Coverage factor (p) 95.45 % y 0.471745 0.471745 Et.pnp 0.0016 Ump 7.4162E-05 16 7.5625E-20 L.massett 0.5008 Upp 4.85627E-05 3 1.1587E-19 Umassett 0.000482183 8 Et. 0.000752 0 0 0 0 0 Calibrated value 0.470993000 6.23996E-07 ∞ 0 0 Effective degree of freedom free		0.471600	0.471700	0.471800	0.471800					
S, 4.47214E-05 4.47214E-05 5.47723E-05 0.000122474 S(S)'72 2E-09 2E-09 3E-09 1.5E-08 (S)'72 2E-09 3E-09 3E-09 1.5E-08 (S)'72 1.5625E-08 6.25E-10 9.025E-09 3.025E-09 3	5-5	0.471700	0.471700	0.471800	0.471800					
Sj 2	y _i									
Y _j - y										
Coverage factor (p) 95.45 %										
Coverage factor (p) 95.45 % y 0.471745 Degree of freedom (v ₊) U _{rap} 7.4162E-05 16 7.5625E-20 L _{realizat} 0.5008 Degree of freedom U _{geo} 4.85627E-05 3 1.1587E-19 U _{racion} 0.000158226 U _{urar} 0.000158226 9 6.96409E-17 U _{urar} 6.23996E-07 ~ 0 Calibrated value 0.470993000 standard uncertainty 0.000163479 k factor 2.283681613										
y	(y) - y) Z	1.50252-00	0.23E-10	3.023L-03	3.023L-03					
Degree of freedom (v _c) U _c / V _c U _{reap} 7.4162E-05 16 7.5625E-20 L _{reap} L _{reap} Degree of freedom U _{gro} 4.85627E-05 3 1.1587E-19 U _{reap} 0.000482183 Degree of freedom E _L 0.000752 U _{reap} 0.000158226 9 6.96409E-17 U _{sump} 6.23996E-07 ~ 0 Calibrated value 0.470993000 Effective degree of freedom 10 Effective degree of freedom 10 Calibrated value 0.000163479 Effective degree of freedom 10 Calibrated value 0.283681613 Calibrated value 0.283681613 Calibrated value 0.000163479 Calibrated value 0.000	Coverage factor (p)	95.45]%							
Ump 7.4162E-05 16 7.5625E-20 Loneassts 0.5008 Ugeo 4.85627E-05 3 1.1587E-19 Umasssts 0.000482183 Degree of freedom E _L 0.000752 0.000158226 9 6.96409E-17 User 6.23996E-07 0 0 Calibrated value Standard uncertainty 0.000163479 k factor 2.283681613	у	0.471745]				E_{Lprop}	0.0016		
Ump 7.4162E-05 16 7.5625E-20 Loneassts 0.5008 Ugeo 4.85627E-05 3 1.1587E-19 Umasssts 0.000482183 Degree of freedom E _L 0.000752 0.000158226 9 6.96409E-17 User 6.23996E-07 0 0 Calibrated value Standard uncertainty 0.000163479 k factor 2.283681613			Degree of freedom (v _e)	n 4/v						
Upper 4.85627E-05 3 1.1587E-19 Umeast 0.000482183 Degree of freedom E _L 0.000752 9 6.96409E-17 Userr 0.000158226 9 6.96409E-17 Userr 0 0 Calibrated value 0.470993000 Effective degree of freedom 10 standard uncertainty 0.000163479 Effective degree of freedom 10	Uma	7 4162F-05					Lowersett	0.5008		
E _L 0.000752 u _{corr} 0.000158226 9 6.96409E-17 u _{temp} 6.23996E-07 ∞ 0 Calibrated value 0.470993000 Effective degree of freedom 10 standard uncertainty 0.000163479 k factor 2.283681613	-144								Degree of freedom	
U _{torr} 0.000158226 9 6.96409E-17 U _{torr} 6.23996E-07 ∞ 0 Calibrated value 0.470993000 Effective degree of freedom 10 standard uncertainty 0.000163479 In the color of the color o	u _{geo}	4.85627E-05	3	1.1587E-19			Umeasstd	0.000482183	8	
U _{torr} 0.000158226 9 6.96409E-17 U _{torr} 6.23996E-07 ∞ 0 Calibrated value 0.470993000 Effective degree of freedom 10 standard uncertainty 0.000163479 In the color of the color o	-	0.000750	1							
Calibrated value 0.470993000 Standard uncertainty 0.000163479 k factor 2.283681613	EL	0.000752	l							
Calibrated value 0.470993000 Effective degree of freedom 10 standard uncertainty 0.000163479 10 k factor 2.283681613 10	Ucorr	0.000158226	9	6.96409E-17						
standard uncertainty	U _{temp}	6.23996E-07	∞	0						
standard uncertainty			•	-						
k factor 2.283681613	Calibrated value	0.470993000		Effective degree of freedom	10					
k factor 2.283681613	etandard uncertainty	0.000163470								
	Standard uncertainty	0.000103479	I							
Extended uncertainty 0 000373333	k factor	2.283681613								
	Extended uncertainty	0.000373333	1							

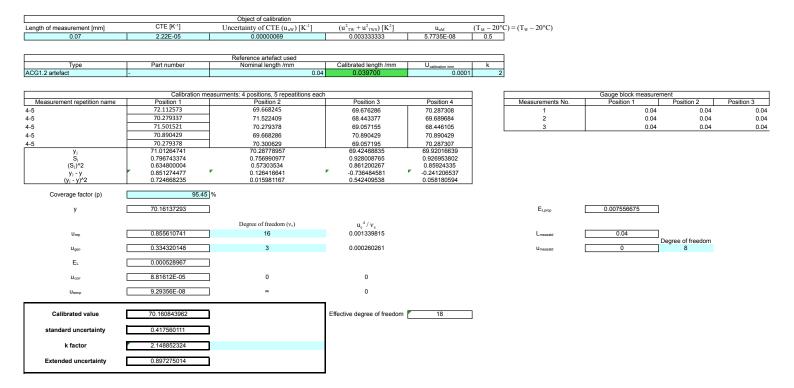
Appendix (10)

CALCULATION OF LENGTH CALIBRATION

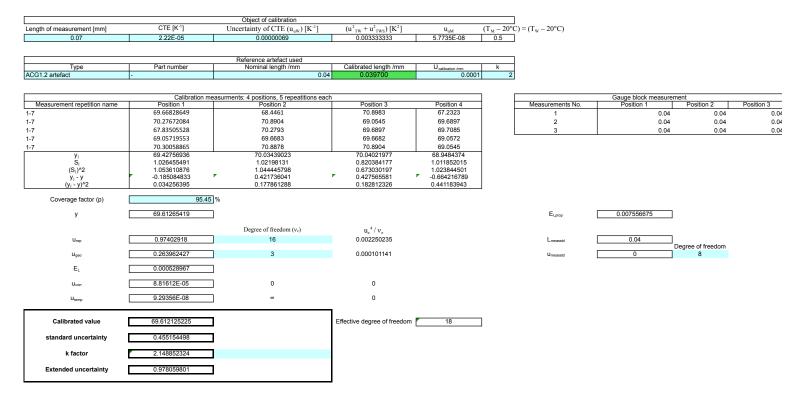




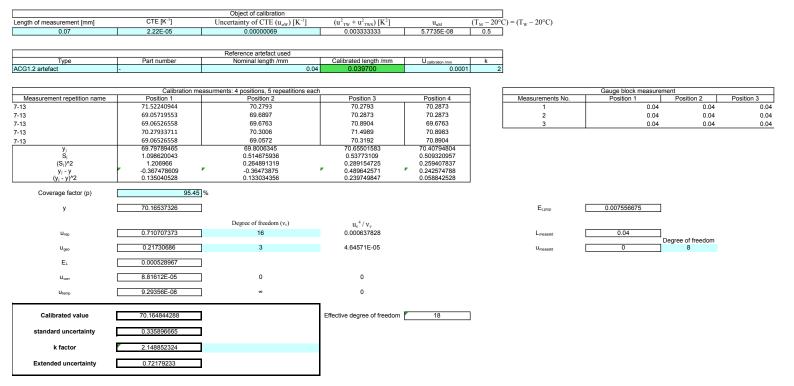
		Object of calibration							
Length of measurement [mm]	CTE [K-1]	Uncertainty of CTE (uaW) [K-1]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	$u_{\alpha M}$	$(T_{\rm M} - 20^{\circ})$	$(C) = (T_W - 20^{\circ}C)$			
0.07	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5				
		Reference artefact used							
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
ACG1.2 artefact	-	0.04	0.039700	0.0001	2				
	Calibration me	easurments: 4 positions, 5 repeatitions each			1		Gauge block measuren	nent	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	1	Measurements No.	Position 1	Position 2	Position 3
3-4	68.446105	69.665606	69.668286	69.054491	1	1	0.04	0.04	0.04
3-4	69.057196	70.279337	69.676326	69.057196		2	0.04	0.04	0.04
3-4	68.487013	69.065266	70.898330	70.276680		3	0.04	0.04	0.04
3-4	68.446105	71.540642	69.676326	71.509315					
3-4	70.287307	69.057155	70.287307	69.057196					
y _i S _i	68.94474509	69.92160119	70.04131506	69.79097543					
(S _i)^2	0.794027674 0.630479947	1.03626461 1.073844343	0.547852829 0.300142722	1.096343105 1.201968205					
(3) 2 y ₁ - y		0.246941997		0.116316242					
(y ₁ - y)^2	0.532774597	0.06098035	0.134436523	0.013529468					
Coverage factor (p)	95.45	1%			_				
ν	69.67465919	 				E _{Lprop}	0.007556675		
y	09.07403919					LLprop	0.007330073		
		Degree of freedom (v _c)	u_e^4/v_e						
U _{rep}	0.895326088	16	0.001606442			L _{measstd}	0.04		
								Degree of freedom	
U _{geo}	0.248616327	3	7.95935E-05			U _{measstd}	0	8	
EL	0.000528967								
Ucorr	8.81612E-05	0	0						
U _{temp}	9.29356E-08	∞	0						
-									
Calibrated value	69.674130225		Effective degree of freedom	18	1				
-tddt-lt	0.419254443				_				
standard uncertainty	0.419254443								
k factor	2.148852324								
Extended uncertainty	0.900915884								
<u> </u>									



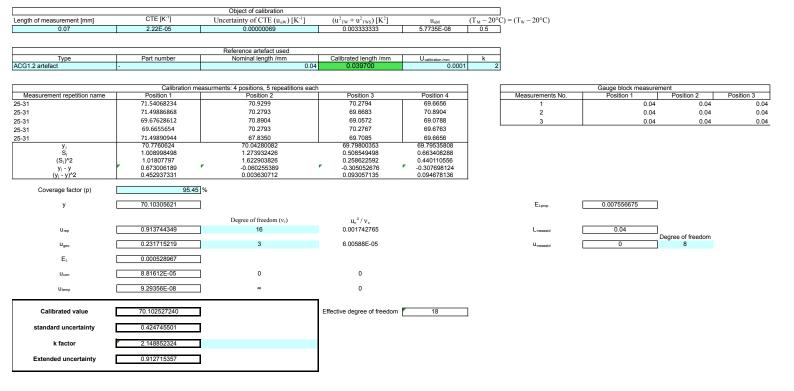
bration measurments: 4 positions, 5 repealitions e Position 2 70.279337 69.057155 69.668245 70.279337 69.668246 77 69.7946388 55 0.511275428 155 0.261402564 66 0.144557055 122 95.45] %	(u² _{TW} + u² _{TWN}) [K²] 0.003333333 Calibrated length /mm 0.04 0.039700 Beach Position 3 69.065306 70.287307 70.890429 69.668246 69.151766 69.151766 69.151766 09.151766 09.151766 09.151768	U _{sh} U _{sh} 5.7735E-08 5.7735E-08 U_sattrouton mm 0.000 Position 4 69.66565 69.668245 71.509355 68.446105 69.889684 69.7957908 1.095723267 1.200609478 0.14983977 0.022465207		surements No. 1 2 3	Gauge block measuren Position 1	ment Position 2 0.04 0.04 0.04	0.04
Reference artefact used r Nominal length /mm 0 bration measurments: 4 positions, 5 repeatitions e Position 2 70,279337 69,057155 69,668245 70,279337 69,668246 70,279337 69,668246 70,279337 69,704338 55 0,511275428 05 0,511275428 05 0,144557055 0,144557055 0,020896742	Calibrated length /mm 0.04 Calibrated length /mm 0.039700 Position 3 69.065306 70.287307 70.890429 68.686246 69.151766 69.81261085 0.775088501 0.600762184 0.166704023	Usattoriton imm 0.000 Position 4 69.665565 69.668245 71.509355 68.446105 69.689684 69.7957908 1.095723267 1.200609478 7.120069478	0.5 k 1 2	ssurements No. 1 2 3	Position 1 0.04 0.04 0.04	Position 2 0.04 0.04	Position 3 0.02 0.04
bration measurments: 4 positions, 5 repealtitions e Position 2 Position 3 Position 3 Position 3 Position 4 Position 4 Position 5 Position 2 Position 6 Position 6 Position 6 Position 6 Position 7 Position 8 Position 9 Pos	0.04 0.03970 Beach Position 3 69.065306 70.287307 70.890429 69.668246 69.151766 69.81261085 0.775088501 0.600762184 0.166704023	0.000 Position 4 69.665656 69.668245 71.509355 68.448105 69.689684 69.7957908 1.095723267 1.200609478 0.149883977	1 2	1 2 3	Position 1 0.04 0.04 0.04	Position 2 0.04 0.04	0.04 0.04
bration measurments: 4 positions, 5 repealtitions e Position 2 Position 3 Position 3 Position 3 Position 4 Position 4 Position 5 Position 2 Position 6 Position 6 Position 6 Position 6 Position 7 Position 8 Position 9 Pos	0.04 0.03970 Beach Position 3 69.065306 70.287307 70.890429 69.668246 69.151766 69.81261085 0.775088501 0.600762184 0.166704023	0.000 Position 4 69.665656 69.668245 71.509355 68.448105 69.689684 69.7957908 1.095723267 1.200609478 0.149883977	1 2	1 2 3	Position 1 0.04 0.04 0.04	Position 2 0.04 0.04	0.04 0.04
bration measurments: 4 positions, 5 repeatitions e Position 2 70.279337 69.057155 69.068245 70.279337 69.68246 7 69.79946388 5 0.511275428 0.51402564 0.144557055 12 0.020896742	0.04 0.03970 Beach Position 3 69.065306 70.287307 70.890429 69.668246 69.151766 69.81261085 0.775088501 0.600762184 0.166704023	0.000 Position 4 69.665656 69.668245 71.509355 68.448105 69.689684 69.7957908 1.095723267 1.200609478 0.149883977	1 2	1 2 3	Position 1 0.04 0.04 0.04	Position 2 0.04 0.04	0.0 ² 0.0 ²
bration measurments: 4 positions, 5 repealitions e Position 2 70.279337 69.057155 69.668245 70.279337 69.668246 77 69.7946388 55 0.511275428 155 0.261402564 66 0.144557055 122 95.45] %	Position 3 69.065306 70.287307 70.890429 69.668246 69.151766 69.81261085 0.775088501 0.600762184 0.166704023	Position 4 69.665565 69.668245 71.509355 68.446105 69.689684 69.7957908 1.095723267 1.20060947		1 2 3	Position 1 0.04 0.04 0.04	Position 2 0.04 0.04	0.04 0.04
Position 2 70.279337 69.057155 69.668245 70.279337 69.668246 70.69.79045388 15 0.511275428 15 0.281402584 16 0.144557055 2 0.020896742	Position 3 69.065306 70.287307 70.89707 70.890429 69.668246 69.151766 69.81261085 0.775088501 0.600762184 0.166704023	69.665565 69.668245 71.509355 68.446105 69.689684 69.7957908 1.095723267 1.200609478 0.149883977	Mea	1 2 3	Position 1 0.04 0.04 0.04	Position 2 0.04 0.04	0.04 0.04
Position 2 70.279337 69.057155 69.668245 70.279337 69.668246 70.69.79045388 15 0.511275428 15 0.281402584 16 0.144557055 2 0.020896742	Position 3 69.065306 70.287307 70.89707 70.890429 69.668246 69.151766 69.81261085 0.775088501 0.600762184 0.166704023	69.665565 69.668245 71.509355 68.446105 69.689684 69.7957908 1.095723267 1.200609478 0.149883977	Mea	1 2 3	Position 1 0.04 0.04 0.04	Position 2 0.04 0.04	0.0 ² 0.0 ²
70.279337 69.057155 69.668245 70.279337 69.668246 7 69.79946388 5 0.511275428 15 0.261402564 66	69.065306 70.287307 70.890429 69.668246 69.151766 69.81261085 0.775088501 0.600762184 0.166704023	69.665565 69.668245 71.509355 68.446105 69.689684 69.7957908 1.095723267 1.200609478 0.149883977	Mea	1 2 3	0.04 0.04 0.04	0.04 0.04	0.0 ² 0.0 ²
69.057155 69.668245 70.279337 69.668246 77. 69.79045388 15. 0.511275428 15. 0.261402564 16. 0.144557055 12. 0.020896742	70.287307 70.890429 69.668246 69.151766 69.81261085 0.775088501 0.600762184 0.166704023	69.668245 71.509355 68.446105 69.689684 69.7957908 1.095723267 1.200609478 0.149883977		2 3	0.04	0.04	0.04
69.668245 70.279337 69.668246 77 69.79046388 155 0.511276428 0.261402564 60 0.144557055 122 0.020896742	70.890429 69.668246 69.151766 69.81261085 0.775088501 0.600762184 0.166704023	71.509355 68.446105 69.689684 69.7957908 1.095723267 1.200609478 0.149883977		3	0.04		
70.279337 69.68246 77 69.79046388 55 0.511275428 55 0.261402564 66 0.144557055 52 0.020896742	69.668246 69.151766 69.81261085 0.775088501 0.600762184 0.166704023	68.446105 69.689684 69.7957908 1.095723267 1.200609478 0.149883977				0.04	0.04
99.68246 77 69.79046388 15 0.511275428 15 0.261402564 10 144557055 10 0.020896742 95.45] %	69.151766 69.81261085 0.775088501 0.600762184 0.166704023	69.689684 69.7957908 1.095723267 1.200609478 0.149883977		E	0.007555575		
77 69.79046338 155 0.511275428 155 0.261402564 156 0.144557055 122 0.020896742	69.81261085 0.775088501 0.600762184 0.166704023	69.7957908 1.095723267 1.200609478 0.149883977		E	0.007556575		
.55 0.511275428 .55 0.261402564 .66 0.144557055 .22 0.020896742 95.45] %	0.775088501 0.600762184 0.166704023	1.095723267 1.200609478 0.149883977		E	0.007558275		
0.261402564 0.66 0.144557055 0.020896742 95.45 %	0.600762184 0.166704023	1.200609478 0.149883977		E	0.007556675		
95.45] %	0.166704023	0.149883977		E	0.007556675		
95.45 %	0.100704020			E	0.007858276		
95.45 %	0.027790231	0.022465207	_	E	0.007556675		
Degree of freedom (v _e)	u_e^4/v_e			∟Lprop	0.007330075		
6 16	0.001665666			$L_{measstd}$	0.04	Degree of freedom	
6 3	1.16531E-05			U _{measstd}	0	8	
7							
5 0	0						
8 ∞	0						
	\neg		_				
55	Effective degree of freedon	n 17					
7							
11							
6							
	05	0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0	0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0	0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0	0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0	0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0	0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0



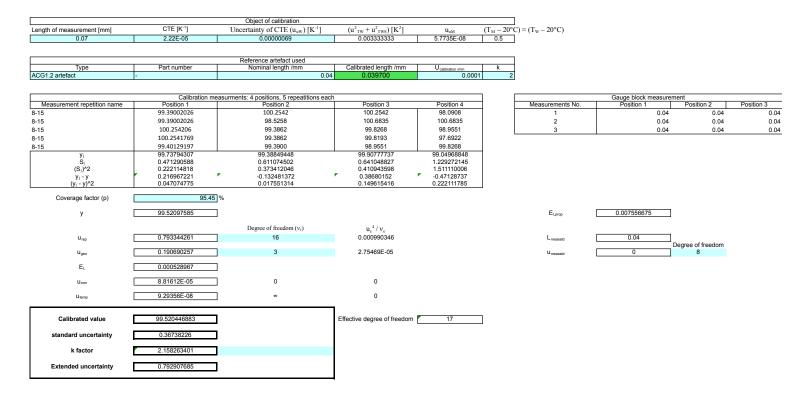
		Object of calibration						
Length of measurement [mm]	CTE [K-1]	Uncertainty of CTE (uaW) [K-1]	$(u^2_{TW} + u^2_{TWS})[K^2]$	$u_{\alpha M}$	(T _M - 20°C	$T(T_W - 20^{\circ}C)$		
0.07	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5			
		Reference artefact used						
Type	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k			
ACG1.2 artefact	-	0.04	0.039700	0.0001	2			
	Calibration me	easurments: 4 positions, 5 repeatitions each	1		٦ - ١		Gauge block measurement	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	1 [Measurements No.	Position 1 Position 2	Position 3
7-13	69.6655654	70.2767	69.0545	70.9825		1	0.04 0.04	(
7-13	69.6762854	70.2767	70.2767	70.2873	1 1	2	0.04 0.04	(
7-13	72.10998336	71.5015	70.2794	69.7325	[3	0.04 0.04	(
7-13	70.27933675	70.8983	69.6683	70.8983				
7-13	69.68972437	70.3006	68.4543	70.2873	1			
y _i S _i	70.28417906 1.053467931	70.65075195 0.544864156	69.54663298 0.793751111	70.43759993 0.512711648				
(S ₁)^2	1.109794682	0.296876949	0.630040826	0.262873234				
y _j - y			-0.683158003	0.20780895				
(y _j - y)^2	0.002958063	0.177208141	0.466704856	0.04318456				
Coverage factor (p)	95.45	1%						
• ",	70.22979098]				E _{Lprop}	0.007556675	
у	10.22919096					⊏Lprop	0.007550075	
		Degree of freedom (v _e)	u_e^4/v_e					
U _{rep}	0.758219244	16	0.000826265			L _{measstd}	0.04	
- rep						massa	Degree of freedom	
Ugeo	0.239801241	3	6.88913E-05			U _{measstd}	0 8	
EL	0.000528967	l						
Ucorr	8.81612E-05	0	0					
U _{temp}	9.29356E-08	∞	0					
		•	1					
Calibrated value	70.229262011		Effective degree of freedom	18	1			
standard uncertainty	0.359660188				_			
standard uncertainty	0.339000100							
k factor	2.148852324							
Extended uncertainty	0.772856631							
			J					



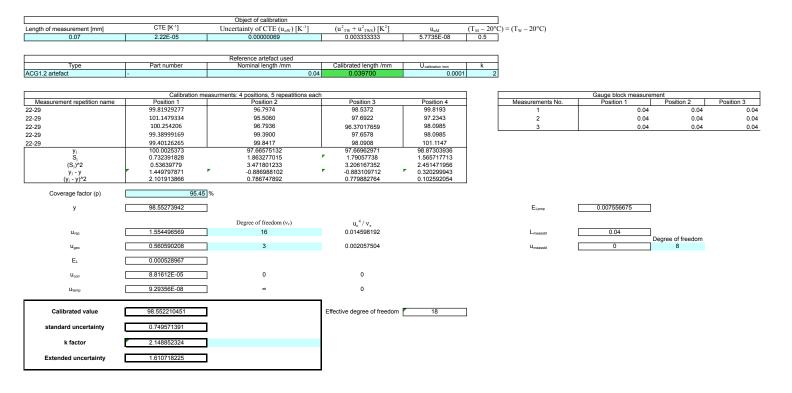
		Object of calibration				1			
ength of measurement [mm]	CTE [K-1]	Uncertainty of CTE (uaW) [K-1]	$(u^2_{TW} + u^2_{TWS})[K^2]$	$u_{\alpha M}$	(T _M - 20°	$C) = (T_W - 20^{\circ}C)$			
0.07	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5				
		Reference artefact used				1			
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
CG1.2 artefact	-	0.04	0.039700	0.000	1 2				
		asurments: 4 positions, 5 repeatitions each	h				Gauge block measure	ment	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	1	Measurements No.	Position 1	Position 2	Position 3
9-25	67.90104612	68.4543	70.2793	70.8904		1	0.04	0.04	0.04
9-25 9-25	69.06530633 69.66828649	69.0572 69.0977	69.6656 69.6683	69.0653 71.4989		2 3	0.04	0.04 0.04	0.04 0.04
9-25 9-25	69.05449148	69.6656	69.0653	69.0977			0.04	0.04	0.04
9-25 9-25	69.06530705	70.9115	70.3006	69.6656					
	68.95088749	69.43725736	69.79581694	70.04356592	1				
y _i S _i	0.642990188	0.92890461	0.513678013	1.098811769					
(S ₁)^2	0.413436382 -0.605994434	0.862863774 -0.119624573	0.263865101 0.238935011	1.207387304 0.486683995					
y _i - y (y _i - y)^2	0.367229253	0.014310038	0.05708994	0.236861311					
					_				
Coverage factor (p)	95.45	%							
у	69.55688193					E _{Lprop}	0.007556675		
•									
		Degree of freedom (v _e)	u_e^4/v_e						
U_{rep}	0.82878715	16	0.001179538			L _{measstd}	0.04		
u_{geo}	0.237256988	3	6.60138E-05			U _{measstd}	0	Degree of freedom 8	
EL	0.000528967								
U _{corr}	8.81612E-05	0	0						
	9.29356E-08	00	0						
U _{temp}	9.29330E-00		U						
					_				
Calibrated value	69.556352961		Effective degree of freedom	18					
standard uncertainty	0.389166231								
k factor	2.148852324								
Extended uncertainty	0.83626076								
		CALCULATION	OF LENGT	TH CALIBI	RATIO	ON			
		CALCULATIO	, or private	II CILID	WILL.	011			



		Object of calibration							
Length of measurement [mm]	CTE [K-1]	Uncertainty of CTE (u _{aW}) [K ⁻¹]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	u_{aM}	(T _M – 20°C	$T(T_W - 20^{\circ}C)$			
0.07	2.22E-05	0.00000069	0.003333333	5.7735E-08	0.5				
		Reference artefact used							
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
ACG1.2 artefact	-	0.04	0.039700	0.0001	2				
		asurments: 4 positions, 5 repeatitions each] [Gauge block measurem		
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	4 1	Measurements No.	Position 1	Position 2	Position 3
1-8	98.52580655	98.9626	98.5371	97.2266		1	0.04	0.04	0.04
1-8	98.95508297	100.6909	98.0908	97.2266		2	0.04	0.04	0.04
1-8	98.09845866	100.2654	99.8193	98.0909		3	0.04	0.04	0.04
1-8	98.52580655	98.1137	97.6616	97.2343					
1-8	98.53717711	99.4013	98.5258	97.2266					
y _j S _i	98.52846637 0.302901956	99.4867874 1.027569916	98.52693708 0.807664043	97.40101939 0.385654551					
(S _i)^2	0.302901956	1.055899933	0.652321207	0.385654551					
y ₁ - y	0.042663809	1.000984843	0.032321207	-1.084783173					
(y _j - y)^2	0.001820201	1.001970657	0.001692049	1.176754532					
Coverage factor (p)	95.45	%							
у	98.48580256					E _{Lprop}	0.007556675		
		Degree of freedom (v _c)	u_e^4/v_e						
U _{rep}	0.697979256	16	0.000593349			L _{measstd}	0.04		
U _{geo}	0.426442399	3	0.00068897			U _{measstd}	0	egree of freedom 8	
EL	0.000528967								
Ucorr	8.81612E-05	0	0						
U _{temp}	9.29356E-08	00	0						
Calibrated value	98.485273592		Effective degree of freedom	15	1				
Cambratoa Talao	00.1002.0002				_				
standard uncertainty	0.37801891								
k factor	2.181165682								
Extended uncertainty	0.824521873								
			1						



		Object of calibration							
gth of measurement [mm]	CTE [K-1]	Uncertainty of CTE (uaW) [K-1]	$(u^2_{TW} + u^2_{TWS})[K^2]$	$u_{\alpha M}$	$(T_{\rm M} - 20^{\circ}$	$C) = (T_W - 20^{\circ}C)$			
0.07	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5	1			
			•	•		-			
		Reference artefact used				7			
Туре	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	l k	+			
31.2 artefact	- art number	0.04		0.0001		1			
51.2 ditolact	-	0.0-	0.003700	0.0001		1			
		asurments: 4 positions, 5 repeatitions each					Gauge block me		
Measurement repetition name	Position 1	Position 2	Position 3	Position 4		Measurements No.	Position 1	Position 2	Position 3
22	98.53717711	97.2266	98.9551	98.9777		1		0.04 0.04	0.0
22	96.36239729	98.5258	98.5258	98.9777		2		0.04 0.04	0.0
22	97.2266064	98.5372	98.9626	100.2654		3		0.04 0.04	0.0
22	96.79743854	97.2343	98.0985	100.2505					
22	97.66159342	97.2266	98.9551	98.1137					
y _i S _j	97.31704255 0.836205455	97.75011434 0.713315022	98.69940662 0.384468152	99.31698716 0.928568699					
(S _j)^2	0.699239563	0.713319022	0.14781576	0.86223983					
y _i - y	-0.953845114	-0.52077333		1.046099494					
(y _i - y)^2	0.909820502	0.271204861	0.183628491	1.094324151					
					-				
Coverage factor (p)	95.45	%							
	98.27088767					F	0.007556675		
у	98.27088767					E _{Lprop}	0.007556675		
		Degree of freedom (v _e)	u_e^4/v_e						
	0.744666616	16	0.000768754			L _{measstd}	0.04		
U _{rep}	0.744000010	10	0.000708734			∟measstd	0.04	Degree of freedom	
Ugeo	0.452675197	3	0.000874794			U _{measstd}	0	8	
EL	0.000528967								
	8.81612E-05	0	0						
Ucorr	6.81612E-05	Ü	Ü						
Utemp	9.29356E-08	80	0						
			1		_				
Calibrated value	98.270358701		Effective degree of freedom	15					
standard uncertainty	0.402659149								
k factor	2.181165682								
K lactor	2.101103082								
Extended uncertainty	0.878266316								
	0.070200010								
			_						



Object of calibration

Length of measurement [mm]	CTE [K-1]	Uncertainty of CTE (uaw) [K-1]	$(u^2_{TW} + u^2_{TWS}) [K^2]$	u_{aM}	(T _M – 20°C	$T = (T_W - 20^{\circ}C)$			
0.07	2.22E-05	0.0000069	0.003333333	5.7735E-08	0.5				
		Reference artefact used							
Type	Part number	Nominal length /mm	Calibrated length /mm	U _{calibration /mm}	k				
ACG1.2 artefact	-	0.0	0.039700	0.000	1 2				
	Calibration me	easurments: 4 positions, 5 repeatitions ea	ch				Gauge block measure	ment	
Measurement repetition name	Position 1	Position 2	Position 3	Position 4	┥ ト	Measurements No.	Position 1	Position 2	Position 3
29-36	97.69217886	99.8641	98.0908	100.2654	7 1	1	0.04	0.04	0.
29-36	98.09084486	102.0375	100.2654	98.0985		2	0.04	0.04	0.
29-36	100.6835025	100.7058	101.1184	98.5220		3	0.04	0.04	0.
29-36	98.09845866	101.1295	101.1184	99.3863					
29-36	99.81929277	100.2505	101.1147	99.3862	╛				
y _i S _i	98.87685552	100.7974749	100.3415299	99.13167051					
(S ₁)^2	1.301857747 1.694833593	0.840620764 0.706643269	1.311138346 1.719083763	0.844688865 0.713499279					
y _j - y		1.010592188	0.554647184	-0.655212192					
(y _j - y)^2	0.828149469	1.021296571	0.307633499	0.429303017					
Coverage factor (p)	95.45	1 ₀ /			_				
Coverage factor (p)	95.45	76							
у	99.7868827]				E _{Lprop}	0.007556675]	
		_							
		Degree of freedom (v _c)	u_e^4/v_e						
U _{rep}	1.099324782	16	0.003651271			L _{measstd}	0.04]	
U _{geo}	0.464254111] 3	0.000967791			U _{meassid}	0	Degree of freedom 8	
ageo	0.101201111	,	0.000007707			Unicassia		Ü	
E∟	0.000528967]							
Ucorr	8.81612E-05	1 0	0						
Goor	0.010122-00	ı	· ·						
U _{temp}	9.29356E-08	∞	0						
			7						
Calibrated value	99.786353735]	Effective degree of freedom	18	7				
		- -			-				
standard uncertainty	0.543678189								

Appendix (11)

$20 \times$

20x																			
		Horizonta	al						Vertical							Diagona	l		
	1	2	3	4	5			1	2	3	4	5			1	2	3	4	5
L	6.99468E-05	0.000141	0.00021	0.000281	0.00035		L	6.96127E-05	0.00014	0.00021	0.00028	0.00035		L	9.84858E-05	0.000198	0.000296	0.000395	0.00049
σ1	0.482818089	0.77828	0.470639	0.00581	0.312163		σ1	0.177458642	0.179558	0.313841	0.308724	0.894255		σ1	0.321891301	0.582289	0.345817	0.593761	0.723216
σ2	0.475215889	0.31146	0.419254	0.41756	0.411294		σ2	0.455154498	0.35966	0.335897	0.389166	0.424746		σ2	0.37801891	0.367382	0.402659	0.749571	0.54367
σ3	0.000818377	0.001647	0.002462	0.003283	0.004098		σ3	0.000814468	0.001636	0.002457	0.003271	0.004091		σ3	0.001152284	0.002317	0.003466	0.00462	0.005787
σ4	8.18377E-05	0.000165	0.000246	0.000328	0.00041		σ4	8.14468E-05	0.000164	0.000246	0.000327	0.000409		σ4	0.000115228	0.000232	0.000347	0.000462	0.000579
σtotal	0.67745415	0.838289	0.630303	0.417614	0.516358		Ototal	0.488526209	0.401994	0.459705	0.496761	0.990009		σtotal	0.496501407	0.688503	0.530788	0.956259	0.904799

σ1= standard deviation /sqrt(3)

σ2= standard uncertainty calibration of each length

σ3= (L*11.7*1) L=m /σ_{steel}=11.7 /ΔT=(21-20 C°)

σ4= (L*10%*11.7*1)

L= uncertainty calculation of length

		σ1 calculat	ion		
	L1	L2	L3	L4	L5
Difference1	68.96023276	140.5617	208.8559	279.7736	348.0773
Difference2	69.6043758	142.5393	209.5171	279.7812	349.3979
Difference3	70.96629937	139.2605	207.5548	279.7977	348.8235
Mean	69.84363598	140.7872	208.6426	279.7841	348.7663
SD	0.836265462	1.34802	0.815171	0.010063	0.540682
SD/sqrt(3)	0.482818089	0.77828	0.470639	0.00581	0.312163

		σ1 calculat	on		
	L1	L2	L3	L4	L5
Difference1	70.26409381	138.5583	209.476	277.1137	346.0739
Difference2	69.60747316	139.2149	210.1448	276.479	346.0864
Difference3	69.6167644	139.2211	210.8075	277.7886	349.3658
Mean	69.82944379	138.9981	210.1428	277.1271	347.1754
SD	0.307367384	0.311003	0.543588	0.534725	1.548895
SD/sqrt(3)	0.177458642	0.179558	0.313841	0.308724	0.894255

Vertical

0.00021

0.3358967

0.0024571

0.0002457

0.0002796 0.0003497

0.4247455 0.0040911

0.0004091

0.6327565 0.8691175

0.3891662

0.0032709

0.0003271

0.00014

0.35966

0.000164

 $0.409221393 \quad 0.717487 \quad 0.8316435$

0.00006961

0.455154498

0.00008145

0.000814468 0.001636

		σ1 calculat	ion		
	L1	L2	L3	L4	L5
Difference1	98.90958283	197.8192	294.8895	394.7276	492.2388
Difference2	99.36843441	200.1266	295.322	394.2229	492.6758
Difference3	98.02506044	199.7372	296.3199	396.6126	495.0875
Mean	98.76769256	199.2277	295.5104	395.1877	493.334
SD	0.557532088	1.008554	0.598973	1.028425	1.252647
SD/sqrt(3)	0.321891301	0.582289	0.345817	0.593761	0.723216

Diagonal

0.000296

0.733584

0.402659

0.003466

0.000347

0.000395 0.000495

1.29815

0.543678

0.005787

0.000579

0.587132

0.749571

0.00462

0.000462

0.000198

1.34334

0.367382

0.002317

0.000232

9.84858E-05

0.164982479

0.37801891

0.001152284

0.000115228

σ3

10×

		Horizonta	al		
	1	2	3	4	5
L	6.99468E-05	0.000141	0.00021	0.000281	0.00035
σ1	0.618653329	0.398881	0.629795	0.471442	0.396946
σ2	0.475215889	0.31146	0.419254	0.41756	0.411294
σ3	0.000818377	0.001647	0.002462	0.003283	0.004098
σ4	8.18377E-05	0.000165	0.000246	0.000328	0.00041
σtotal	0.780104326	0.506079	0.756586	0.629781	0.571617

σ1= standard deviation /sqrt(3)

 $\sigma 2\text{=}$ standard uncertainty calibration of each length

σ3= (L*11.7*1) L=m /σ_{steel}=11.7 /ΔT=(21-20 C*) σ4= (L*10%*11.7*1)

L= uncertainty calculation of length

Q1 calculation									
	L1	L2	L3	L4	L5				
Difference1	70.14947979	141.1757	208.7803	283.329	349.9888				
Difference2	68.44096592	139.4834	207.8738	281.572	349.1083				
Difference3	71.0208	140.3379	210.5038	283.2782	350.7918				
Mean	69.87041524	140.3323	209.0527	282.7264	349.963				
SD	1.071538998	0.690882	1.090838	0.816561	0.68753				
SD/sqrt(3)	0.618653329	0.398881	0.629795	0.471442	0.396946				

σ1 calculation									
	L1	L2	L3	L4	L5				
Difference1	66.65986969	139.4396	208.72895	276.24255	345.53194				
Difference2	67.51929327	136.792	206.95796	275.37084	344.66023				
Difference3	68.39602028	139.4168	210.48631	278.00561	348.19891				
Mean	67.52506108	138.5495	208.72441	276.53966	346.13036				
SD	0.708792245	1.242725	1.4404488	1.0959664	1.5053557				
SD/sqrt(3)	0.409221393	0.717487	0.8316435	0.6327565	0.8691175				

σ1 calculation								
	L1	L2	L3	L4	L5			
Difference1	97.96646134	198.4127	293.8913	393.7119	492.9105			
Difference2	97.35639127	193.473	292.6716	395.0622	487.4929			
Difference3	97.95861367	198.4048	295.7612	396.1998	491.0605			
Mean	97.76048876	196.7635	294.1081	394.9913	490.4879			
SD	0.285758036	2.326733	1.270604	1.016942	2.248461			
SD/sqrt(3)	0.164982479	1.34334	0.733584	0.587132	1.29815			

Appendix (12) – Zygo data

X1	X2	X2 X3	X4	X5	Mean	SD	SD/sqrt(5)
2 265.12(3 3 437.536 4 605.455 5 782.366 6 948.78 7 92.70; 8 263.62; 9 433.038 10 605.455 11 773.37; 12 948.78 13 92.70; 14 262.12; 15 434.53; 16 605.454 17 771.87; 18 947.28; 19 88.207 20 260.62 21 433.03; 22 602.456 23 771.87; 24 945.78; 25 80.710 26 257.626 27 430.046 28 602.456 29 776.37; 30 948.78 31 86.707 32 256.125 33 431.535				91.2057	36.9310	1.1994	0.536388
3 437.536 4 605.454 5 782.366 6 948.78 7 92.707 8 263.627 9 433.038 10 605.454 11 773.377 12 948.78 13 92.707 14 262.122 15 434.538 16 605.454 17 771.877 18 947.287 20 260.62 21 433.038 22 602.456 23 771.873 24 945.788 25 80.710 26 257.624 27 430.036 29 776.373 30 948.78 31 86.707 32 256.125 33 431.538					107.8188		0.683772
4 605.454 5 782.366 6 948.78 7 92.705 8 263.621 9 433.038 10 605.454 11 773.377 12 948.78 13 92.705 14 262.122 15 434.538 16 605.454 17 771.873 18 947.282 19 88.207 20 260.62 21 433.038 22 602.456 23 771.873 24 945.788 25 80.710 26 257.622 27 430.044 28 602.456 29 776.373 30 948.78 31 86.707 32 256.125						0.734504	0.32848
5 782.368 6 948.78 7 92.700 8 263.621 9 433.038 10 605.454 11 773.377 12 948.78 13 92.7007 14 262.122 15 434.538 16 605.454 17 771.873 18 947.281 19 88.207 20 260.62 21 433.038 22 602.456 23 771.873 24 945.788 25 80.710 26 257.624 27 430.03 28 602.456 29 776.371 30 948.78 31 86.707 32 256.125 33 431.533					246.9055		0.32848
6 948.78 7 92.705 8 263.621 9 433.038 10 605.454 11 773.372 12 948.78 13 92.705 14 262.122 15 434.538 16 605.454 17 771.872 18 947.287 18 947.287 20 260.62 21 433.038 22 602.456 23 771.872 24 945.788 25 80.710 26 257.624 27 430.036 29 776.373 30 948.78 31 86.707 32 256.125				780.869	317.9155		0.781925
7 92.705 8 263.621 9 433.038 10 605.454 11 773.377 12 948.78 13 92.705 14 262.122 15 434.538 16 605.454 17 771.873 18 947.287 19 88.207 20 260.62 21 433.038 22 602.456 23 771.873 24 945.788 25 80.710 26 257.624 27 430.0406 29 776.371 30 948.787 31 86.707 32 256.125				948.787	317.9155 387.0922		0.536386
8 263.621 9 433.036 10 605.454 11 773.377 12 948.78 13 92.700 14 262.122 15 434.538 16 605.454 17 771.873 18 947.281 19 88.207 20 260.62 21 433.038 22 602.456 23 771.873 24 945.788 25 80.710 26 257.622 27 430.040 28 602.456 29 776.373 30 948.788 31 86.707 32 256.125						1.199395	0.536386
9 433.038 10 605.454 11 773.372 12 948.78 13 92.703 14 262.122 15 434.538 16 605.454 17 771.873 18 947.282 19 88.207 20 260.62 21 433.038 22 602.456 23 771.873 24 945.788 25 80.710 26 257.624 27 430.044 28 602.456 29 776.373 30 948.78 31 86.707 32 256.125 33 431.538							
10 605.454 11 773.37 12 948.78 13 92.709 14 262.122 15 434.538 16 605.454 17 771.87 18 947.28 19 88.207 20 260.62 21 433.038 22 602.456 23 771.87 24 945.788 25 80.710 26 257.624 27 430.33 24 948.78 30 948.78 31 86.707 32 256.125 33 431.538						1.799113	0.804588
11 773.372 12 948.78 13 92.701 14 262.122 15 434.538 16 605.454 17 771.873 18 947.287 19 88.207 20 260.62 21 433.038 22 602.456 23 771.873 24 945.788 25 80.710 26 257.622 27 430.040 28 602.456 29 776.371 30 948.787 31 86.707 32 256.125 33 431.538					177.2399		0.781919
12 948.78 13 92.700 14 262.122 15 434.538 16 605.454 17 771.873 18 947.281 19 88.207 20 260.62 21 433.038 22 602.456 23 771.873 24 945.788 25 80.710 26 257.622 27 430.040 28 602.456 29 776.373 30 948.78 31 86.707 32 256.125						1.121941	0.501747
13 92.703 14 262.122 15 434.538 16 605.454 17 771.873 18 947.283 19 88.207 20 260.62 21 433.038 22 602.456 23 771.873 24 945.788 25 80.710 26 257.624 27 430.046 28 602.456 29 776.373 30 948.78 31 86.707 32 256.125 33 431.538						1.799133	0.804597
14 262.122 15 434.538 16 605.455 17 771.873 18 947.283 19 88.207 20 260.62 21 433.038 22 60.2456 23 771.873 24 945.788 25 80.710 26 257.624 27 430.044 28 602.456 29 776.373 30 948.787 31 86.707 32 256.125 33 431.538					386.3589		0.909494
15 434.538 16 605.454 17 771.873 18 947.283 19 88.207 20 260.62 21 433.038 22 602.452 23 771.873 24 945.788 25 80.710 26 257.624 27 430.040 28 602.456 29 776.373 30 948.783 31 86.707 32 256.125 33 431.538						1.748428	0.781921
16 605.454 17 771.875 18 947.281 19 948.287 20 260.62 21 433.038 22 602.455 23 771.875 24 945.788 25 80.710 26 257.622 27 430.040 28 602.456 29 776.371 30 948.788 31 86.707 32 256.125 33 431.533				260.623		1.121973	0.501762
17 771.873 18 947.283 19 88.207 20 260.62 21 433.034 22 602.456 23 771.873 24 945.788 25 80.710 26 257.624 27 430.046 28 602.456 29 776.373 30 948.788 31 86.707 32 256.125 33 431.533					177.1177		0.424052
18 947.287 19 88.207 20 260.62 21 433.038 22 602.456 23 771.873 24 945.788 25 80.710 26 257.624 27 430.046 28 602.456 29 776.373 30 948.788 31 86.707 32 256.125 33 431.538						1.121941	0.501747
19 88.207 20 260.62 21 433.038 22 602.456 23 771.873 24 945.788 25 80.710 26 257.624 27 430.040 28 602.456 29 776.373 30 948.78 31 86.707 32 256.125 33 431.533						1.642364	0.734488
20 260.62 21 433.034 22 602.455 23 771.875 24 945.788 25 80.710 26 257.622 27 430.040 28 602.456 29 776.371 30 948.783 31 86.707 32 256.125					385.9922		0.268203
21 433.038 22 602.456 23 771.873 24 945.788 25 80.710 26 257.622 27 430.044 28 602.456 29 776.371 30 948.78 31 86.707 32 256.125 33 431.538				88.2072		0.734504	0.32848
22 602.456 23 771.873 24 945.784 25 80.710 26 257.624 27 430.046 28 602.456 29 776.373 30 948.78 31 86.707 32 256.125 33 431.535					105.8633		0.804588
23 771.873 24 945.788 25 80.710 26 257.624 27 430.044 28 602.456 29 776.373 30 948.78 31 86.707 32 256.125 33 431.535					1 76.6288		1.153558
24 945.788 25 80.710 26 257.624 27 430.040 28 602.456 29 776.371 30 948.78 31 86.707 32 256.125 33 431.535					245.6833		0.656944
25 80.710 26 257.624 27 430.040 28 602.456 29 776.371 30 948.78 31 86.707 32 256.125 33 431.535	34 770.3741	4 770.3741 773.372	6 770.3741		314.7378		0.781919
26 257.624 27 430.040 28 602.456 29 776.371 30 948.78 31 86.707 32 256.125 33 431.535	84 945.7884	4 945.7884 948.78			385.8700		0.536406
27 430.040 28 602.456 29 776.371 30 948.78 31 86.707 32 256.125 33 431.535	8 83.7094	83.7094 85.2086	86.7079		34.3644	2.033708	0.909502
28 602.456 29 776.371 30 948.78 31 86.707 32 256.125 33 431.539	5 257.6245	5 257.6245 259.123	7 259.1237	262.1223	105.6188	1.642364	0.734488
29 776.371 30 948.78 31 86.707 32 256.125 33 431.539	3 431.5395	3 431.5395 434.538	1 431.5395	433.0388	1 76.1400	1.528965	0.683774
30 948.78 31 86.707 32 256.125 33 431.539	603.9553	1 603.9553 600.956	8 603.9553	606.9539	2 46.0500	1 .989007	0.889511
31 86.707 32 256.125 33 431.539	2 773.3726	2 773.3726 773.372	6 773.3726	774.8719	315.5933	1.19944	0.536406
32 256.125 33 431.539	7 948.787	948.787 947.287	7 947.2877	945.7884	* 386.2367	1.121973	0.501762
33 431.539	9 83.7094	83.7094 88.2072	86.7079	85.2086	35.0977	1.528961	0.683772
	257.6245	2 257.6245 254.625	9 259.1237	256.1252	1 04.6411	1.528961	0.683772
34 600.956	5 431.5395	5 431.5395 431.539	5 433.0388	430.0403	175.8955	0.948209	0.424052
	8 600.9568	8 600.9568 602.456	1 602.4561	602.4561	245.3167	0.734504	0.32848
35 776.371	2 771.8734	2 771.8734 776.371	2 776.3712	774.8719	315.9600	1.748432	0.781922
36 950.286	944.2892	2 944.2892 947.287	7 945.7884	947.2877	385.9922	1.988986	0.889502

	Y1	Y2	Y3	Y4	Y5	Mean	SD	SD/sqrt(5)
1	94.2042	94.2042	95.7035	95.7035	95.7035	38.7643	0.734504	0.32848
2	91.2057	94.2042	95.7035	94.2042	94.2042	38.2754	1.468971	0.656944
3	95.7035	95.7035	94.2042	97.2028	95.7035	3 9.0087	0.948241	0.424066
4	97.2028	97.2028	100.2013	98.702	98.702	40.1087	1.121931	0.501743
5	95.7035	98.702	98.702	100.2013	97.2028		1.528949	0.683767
6	97.2028	98.702	100.2013	95.7035			2.120288	0.948222
7	265.1208	266.6201	262.1223	265.1208		1 08.1855		0.889502
8	263.6215	265.1208	263.6215	268.1193		108.4299		1.089425
9	265.1208	269.6186	266.6201	269.6186		1 09.0410		0.804588
10	266.6201	266.6201	266.6201	268.1193		1 08.7966		0.268185
11	271.1179	271.1179	269.6186	271.1179		1 10.3854		0.268203
12	269.6186	271.1179	271.1179	272.6171		1 10.6299		0.501743
13	436.0373	437.5366	439.0359	437.5366		178.4621		0.501762
14	439.0359	439.0359	436.0373	440.5351		1 78.8288		0.656949
15	437.5366	439.0359	439.0359	440.5351		178.9510		0.424052
16	437.5366	436.0373	436.0373	436.0373		177.7288		0.424052
17	442.0344	440.5351	440.5351	436.0373		1 79.3177		0.909503
18	442.0344	443.5337	440.5351	440.5351		1 80.2954		0.781925
19	611.4517	606.9539	608.4531	609.9524		248.2499		0.683774
20	609.9524	611.4517	609.9524	611.4517		2 48.8610		0.32848
21	609.9524	612.951	611.4517	611.4517		249.1055		0.501762
22	611.4517	605.4546	608.4531	609.9524		248.0055		0.948222
23	612.951	612.951	611.4517	611.4517		249.7166		0.501747
24	612.951	614.4502	614.4502	612.951		249.9610		0.501743
25	777.8704	776.3712	779.3697	779.3697		317.1822		0.501747
26	783.8675	785.3668	780.869	780.869		318.8933		0.848111
27	777.8704	779.3697	780.869	779.3697		317.6711		0.424066
28	779.3697	780.869	782.3682	780.869		318.2822		0.424052
29	783.8675	785.3668	783.8675	783.8675		319.5044		0.424066
30	783.8675	786.866	785.3668	785.3668		319.8711		0.683774
31	953.2848	951.7855	950.2862	950.2862		387.9478		0.59972
32	953.2848	953.2848	954.784	951.7855		388.5589		0.424052
33	956.2833	953.2848	957.7826	953.2848		389.4144		0.804588
34	950.2862	951.7855	954.784	953.2848		388.5589		0.948222
35	945.7884	953.2848	957.7826	948.787		387.9478		1.848429
36	948.787	954.784	959.2818	951.7855	956.2833	388.9255	3.623121	1.620309

Alicona data

20x						
	X1	X2	Х3	Mean	SD	SD/sqrt(3)
1	70.2123	67.2139	68.7131	30.10	1.224092	0.70673
2	227.6272	226.128	230.6256	99.92	1.869831	1.079547
3	391.0389	392.5381	386.5413	170.84	2.54815	1.471175
4	546.9546	545.4554	542.4571	238.69	1.869786	1.079522
5	708.8671	705.8687	707.3679	309.83	1.224092	0.70673
6	864.7828	864.7828	864.3828	378.72	0.188562	0.108866
7	68.7131	65.7147	65.7147	29.22	1.413459	0.816061
8	227.6272	229.1264	221.6305	99.04	3.238596	1.869804
9	391.0389	392.5381	389.5397		1.224092	0.70673
10	545.4554	546.9546	543.9562		1.224092	0.70673
11	704.3695	704.3695	702.8703		0.70673	0.408031
12	866.282	861.7844	861.7844		2.120189	1.224092
13	67.2139	67.2139	65.7147	29.22		0.408031
14	226.128	224.6288	223.1297	98.39	1.224051	0.706706
15	389.5397	391.0389	389.5397	170.84	0.70673	0.408031
16	543.9562	543.9562	543.8956	238.24	0.028558	0.016488
17	704.3695	704.3695	701.3712	308.08		0.816034
18	864.7828	864.7828	864.6828	378.76	0.04714	0.027217
19	67.2139	70.2123	62.7164	29.22		1.778539
20	220.1313	221.6305	226.128	37.31	2.548104	1.471149
21	392.5381	389.5397	386.5413	170.62	2.448183	1.413459
22	542.4571	542.4571	543.9562	237.02	0.706683	0.408003
23	702.8703	702.8703	704.3695		0.70673	0.408031
24	864.7828	866.282	861.7844	370.50	1.869831	1.079547
25	68.7131	67.2139	61.2172		3.238596	1.869804
26	223.1297	223.1297	221.6305		0.70673	0.408031
27	386.5413	388.0405	389.5397		1.224092	0.70673
28	542.4571	543.9562	542.4571		0.706683	0.408003
29	701.3712	701.3712	705.8687	307.86	2.120142	1.224064
30	.2836 702.8		860.2853	377.13	0.74955	0.432753
31	65.7147	68.7131	62.7164		2.448143	1.413436
32	223.1297	224.6288	220.1313	97.51		1.079527
33	388.0405	385.0421	382.0438		2.448143	1.413436
34	537.9595	540.9579	540.9579	230.30		0.816061
35	702.8703	702.8703	699.872	307.42		0.816034
36	860.2853	857.2869	860.2853	376.37	1.413459	0.816061

1					
					1 1 (2)
					SD/sqrt(3)
		_	_	_	0.71
		_	_	_	0.71
					1.22
					1.08
				1.22	0.71
			_		1.41
_			_		0.82
			_	0.7 ±	0.41
		_	_		0.41
-				1.22	0.71
-				0.71	0.41
				1.41	0.82
				1.41	0.82
					0.82
			_	_	1.08
			_	_	1.78
				_	0.00
			_	_	0.82
					0.71
			_		1.08
					0.71
			_		0.00
				1.07	1.08
		_	_	_ 1.07	1.08
		_	_	_ 0.00	0.00
				_ 1.41	0.82
				_ 1.22	0.71
					2.86
			_	_	0.71
			_	_	1.87
			_	_	1.47
		_	_	_	0.82
				_	0.41
		_	_	_ 1.22	0.71
	867.7788		_		1.78
861.782	864.7804	867.7788	378.77	2.45	1.41
	Y1 62.7139 65.7123 70.2099 71.7091 71.7091 68.7107 223.1272 224.6264 226.1256 229.124 232.1224 379.0429 383.5405 382.0413 382.0413 382.0413 382.0413 385.0397 540.9554 539.4562 543.9538 542.4546 545.453 695.372 702.8679 704.3671 705.8663 702.8679 852.7869 864.7804 863.2812 860.2828 861.782	62.7139 64.2131 65.7123 64.2131 70.2099 70.2099 71.7091 70.2099 71.7091 68.7107 68.7107 65.7123 223.1272 223.1272 224.6264 223.1272 226.1256 224.6264 229.124 232.1224 232.1224 232.1224 379.0429 382.0413 383.5405 383.5405 382.0413 385.0397 540.9554 543.9538 539.4562 543.9538 543.9538 545.453 542.4546 542.4546 542.4546 546.9522 545.453 546.9522 545.453 546.9522 545.453 546.9522 545.453 546.9522 545.453 546.9522 545.453 546.9522 545.453 546.9522 545.456 546.9522 545.457 702.8679 704.3671 702.8679	62.7139 64.2131 61.2147 65.7123 64.2131 67.2115 70.2099 70.2099 65.7123 71.7091 70.2099 67.2115 71.7091 68.7107 70.2099 68.7107 65.7123 62.7139 223.1272 223.1272 220.1288 224.6264 223.1272 224.6264 226.1256 224.6264 224.6264 229.124 227.6248 226.1256 232.1224 232.1224 230.6232 232.1224 232.1224 229.124 379.0429 382.0413 379.0429 383.5405 383.5405 380.5421 382.0413 379.0429 374.5454 382.0413 382.0413 382.0413 385.0397 388.0381 540.9554 543.9538 542.4546 542.4546 542.4546 542.4546 542.4546 542.4546 542.4546 542.4546 542.4546 542.4546 542.4546 542.45	62.7139 64.2131 61.2147 27.47 65.7123 64.2131 67.2115 28.78 70.2099 70.2099 65.7123 30.10 71.7091 70.2099 67.2115 30.53 71.7091 68.7107 70.2099 73.075 68.7107 65.7123 62.7139 28.78 223.1272 220.1288 97.29 224.6264 223.1272 224.6264 98.17 226.1256 224.6264 224.6264 98.61 229.124 227.6248 226.1256 99.70 232.1224 232.1224 230.6232 101.45 232.1224 232.1224 239.124 101.23 379.0429 382.0413 379.0429 166.46 383.5405 380.5421 167.55 382.0413 379.0429 374.5454 165.80 382.0413 382.0413 382.0413 382.0413 382.0413 382.0413 382.0413 167.33 385.0397 388.0381 167.33	62.7139 64.2131 61.2147 27.47 1.224092 65.7123 64.2131 67.2115 28.78 1.22 70.2099 70.2099 65.7123 30.10 2.12 71.7091 70.2099 67.2115 30.53 1.87 71.7091 68.7107 70.2099 30.75 1.22 68.7107 65.7123 62.7139 28.78 2.45 223.1272 223.1272 220.1288 97.29 1.41 224.6264 223.1272 224.6264 98.61 0.71 226.1256 224.6264 224.6264 98.61 0.71 229.124 227.6248 226.1256 99.70 1.22 232.1224 232.1224 230.6232 101.45 0.71 232.1224 232.1224 229.124 101.23 1.41 383.5405 380.5421 167.55 1.41 382.0413 379.0429 374.5454 165.80 3.08 382.0413 382.0413 382.0413

Appendices

10x]					
	X1	X2	Х3	Mean	SD	SD/sqrt(3)
1	37	40	38	33.61	1.247219	0.7200823
2	117	118	119	1 03.46	0.816497	0.471404521
3	198	199	198	1 73.90	0.471405	0.272165527
4	275	277	278	242.58	1.247219	0.7200823
5	360	361	361	316.23	0.471405	0.272165527
6	436	438	438	383.45	0.942809	0.544331054
7	39	39	38	33.90	0.471405	0.272165527
8	117	117	118	1 02.88	0.471405	0.272165527
9	199	200	200	1 75.07	0.471405	0.272165527
10	276	276	275	241.70	0.471405	0.272165527
11	360	356	356	313.31	1.885618	1.088662108
12	437	436	437	382.87	0.471405	0.272165527
13	38	40	39	3 4.20	0.816497	0.471404521
14	116	118	118	1 02.88	0.942809	0.544331054
15	199	196	199	7 173.61	1.414214	0.816496581
16	275	277	276	242.00	* 0.816497	0.471404521
17	359	358	356	313.60	1.247219	0.7200823
18	437	437	4387	1 537.61	1 862.048	1075.053832
19	36	38	36	32.15	0.942809	0.544331054
20	115	116	117	1 01.71	0.816497	0.471404521
21	197	197	198	1 73.02	0.471405	0.272165527
22	276	276	2776	972.66	1178.511	680.4138174
23	357	355	358	312.73	1.247219	0.7200823
24	438	436	439	383.75	1.247219	0.7200823
25	36	36	37	31.86	0.471405	0.272165527
26	115	116	116	1 01.42	0.471405	0.272165527
27	196	197	197	172.44	0.471405	0.272165527
28	276	274	275	241.12	0.816497	0.471404521
29	356	355	357	312.14	0.816497	0.471404521
30	437	435	436	382.28	0.816497	0.471404521
31	38	38	40	33.90	0.942809	0.544331054
32	114	114	115	1 00.25	0.471405	0.272165527
33	197	197	199	173.31	0.942809	0.544331054
34	273	273	274	2 39.66	0.471405	0.272165527
35	353	354	354	310.09	0.471405	0.272165527
36	436	432	434	380.53	1.632993	0.942809042

10x	1					
	Y1	Y2	Y3	Mean	SD	SD/sqrt(3)
1	32.4416	32.4416	30.688	31.86	0.826655	0.477269
2	38	34	35	31.27	1 .699673	0.981307
3	37	36	38	32.44	0.816497	0.471405
4	41	36	36	33.03	2.357023	1.360828
5	39	39	36	33.32	1.414214	0.816497
6	37	37	36	32.15	0.471405	0.272166
7	113	114	113	99.37	0.471405	0.272166
8	115	117	114	1 01.12	1.247219	0.720082
9	115	114	115	1 00.54	0.471405	0.272166
10	115	114	117	1 01.12	1.247219	0.720082
11	117	115	117	102.00	0.942809	0.544331
12	118	117	117	102.88	0.471405	0.272166
13	196	193	194	1 70.39	1.247219	0.720082
14	196	196	194	171.27	0.942809	0.544331
15	195	193	194	170.10	* 0.816497	0.471405
16	193	193	195	1 69.81	6 0.942809	0.544331
17	194	193	195	170.10	5 0.816497	0.471405
18	194	191	196	1 69.81	2.054805	1.186342
19	275	273	275	240.54	0.942809	0.544331
20	275	274	274	240.54	0.471405	0.272166
21	274	275	277	241.41	1.247219	0.720082
22	272	273	274	239.37	0.816497	0.471405
23	274	275	275	2 40.83	0.471405	0.272166
24	272	274	273	239.37	0.816497	0.471405
25	352	351	352	308.34	0.471405	0.272166
26	352	353	353	309.22	0.471405	0.272166
27	357	354	353	310.97	1.699673	0.981307
28	357	357	358	313.31	0.471405	0.272166
29	353	359	355	311.85	2.494438	1.440165
30	350	362	356	312.14	4.898979	2.828427
31	431	430	432	377.90	0.816497	0.471405
32	430	432	430	377.61	0.942809	0.544331
33	429	433	434	378.78	2 .160247	1.247219
34	431	433	433	379.07	0.942809	0.544331
35	434	435	433	380.53	0.816497	0.471405
36	433	431	431	378.49	7 0.942809	0.544331

1

59

Appendix (13)

MATLAB code for Resolution (Ch. 7):

```
2
3
 4
 5
     6
     noOfReplication=1;
 7
     filePath ='ANAS Resolution data\';
 8
    filePathFolder=filePath;
9
10
    matVal = zeros(20e6,3); %NOTES: use pre-allocated memory (like in C/C++)
11
     where rhe variables are declared first.
     for j=1:noOfReplication
12
13
         filename='zygo5 1'; %'test alicona';%'test zygo';
         fullName=[filePathFolder '\' filename '.txt'] %string concatenation,
14
15
     alternative to strcat()
16
         fid=fopen(fullName,'r'); %opening the file
17
         pointCounter=0;
18
         line counter=0;
19
20
         while (~feof(fid))
21
            readLine=fgetl(fid);
22
             if (~ischar(readLine))
23
                break
24
             end
25
26
            val=regexp(readLine,' ','split'); %Splitting the string with
27
     certain delimiter
28
            if(size(val, 2) >= 3)
29
                 if(~isnan(str2double(val(3)))) %check if the z value is not NaN
30
                    pointCounter= pointCounter+1;
31
                    matVal(pointCounter,1) = str2double(val(1)); %*delta x;
32
                    matVal(pointCounter, 2) = str2double(val(2)); %*delta y;
33
                    if(strcmp(val(3),'***'))
34
                        matVal(pointCounter, 3) = matVal(pointCounter-1, 3) %use
35
     the previous one
36
37
                        matVal(pointCounter, 3) = str2double(val(3)); %unit in ?
38
                    end
39
                 end
40
             end
41
42
         end %END of while
43
44
         fclose(fid);
45
46
    end %END of the inner for j
47
    matVal(pointCounter+1:end,:) = [];
48
49
     %%CALCULATING the heigth with respect to lateral distance----
50
51
    nLag=pointCounter;
52
     ZhTotal = zeros(nLag, 2*nLag); % column 1=for the value, 2=for the lag index
53
     var = zeros(1,nLag); % column 1=for the value, 2=for the lag index
54
     average heigth=zeros(1,nLag);
55
     lagIndex=zeros(1,nLag);
56
57
     lagIndexCounter=0;
58
     ZhColCounter=0;
```

```
60
      for i=1:pointCounter
 61
           for j=1:pointCounter
 62
               lag=sqrt(sum((matVal(i,:)-matVal(j,:)).^2)); %Euclidean distance
 63
      %abs(matVal(i,1)-matVal(j,1));
 64
               if(j\sim=i)
 65
                   if(i==1)
 66
                        lagIndexCounter=lagIndexCounter+1;
 67
                        lagIndex(lagIndexCounter)=lag; % record all the possible
 68
      lag
 69
                        %ZhColCounter=ZhColCounter+1;
 70
                        ZhTotal(lagIndexCounter, 1) = abs(matVal(i, 3) - matVal(j, 3));
 71
 72
                   else
 73
                        counter=1;
 74
                       while ((lagIndex(counter)-lag) > 0.05)
 75
      %lagIndex(counter)~=lag %if the difference < 0.05 um, they are the same</pre>
 76
                            counter=counter+1;
 77
                            if(counter>nLag)
 78
                                counter=counter-1;
 79
                                break;
 80
                            end
 81
                       end
 82
                        colCounter=1;
 83
                       while (ZhTotal (counter, colCounter) ~=0)
 84
                            colCounter=colCounter+1;
 85
                            if(colCounter>2*nLag)
 86
                                colCounter=colCounter-1;
 87
                                break;
 88
                            end
 89
                        end
 90
                        ZhTotal(counter, colCounter) = abs(matVal(i,3)-matVal(j,3));
 91
                   end
 92
               end
 93
           end
 94
      end
 95
      lagIndex;
 96
      ZhTotal;
 97
 98
      %calculating the average heigth
 99
      average heigth(lagIndexCounter+1:end) = [];
100
      lagIndex(lagIndexCounter+1:end) = [];
101
      for i=1:lagIndexCounter
102
          average heigth(i)=0;
103
           j=1;
104
           colCounter=1;
105
           while ZhTotal(i,colCounter)~=0
106
               average heigth(i) = average heigth(i) + ZhTotal(i, colCounter);
107
               colCounter=colCounter+1;
108
                if (colCounter>2*nLag)
109
                   colCounter=colCounter-1;
110
                   break;
111
                end
112
113
           average_heigth(i) = average_heigth(i) / colCounter;
114
      end
115
      average heigth;
116
117
118
119
      figure;
```

```
120
      plot(lagIndex,average heigth,'.');
121
      ylabel('Average height/um');
122
      xlabel('lateral distance/um');
123
     title('Zygo data');
124
125
     matrix size=size(matVal);
126
127
      %WRITING The data to File: lagIndex, avergae height, ZhTotal
      fullName2=[filePathFolder '\' filename '-lagIndex ZYGO.txt'] %string
128
129
      concatenation, alternative to strcat()
130
      fid2=fopen(fullName2,'w');
131
      for i=1:length(lagIndex)
132
          fprintf(fid2,'%f\n',lagIndex(i));
133
      end
134
      fclose(fid2);
135
136
     fullName2=[filePathFolder '\' filename '-averageHeight ZYGO.txt'] %string
137
     concatenation, alternative to strcat()
138
     fid2=fopen(fullName2,'w');
139
     for i=1:length(lagIndex)
140
          fprintf(fid2,'%f\n',average heigth(i));
141
142
     fclose(fid2);
143
144
      fullName2=[filePathFolder '\' filename '-zhTotal ZYGO.txt'] %string
145
      concatenation, alternative to strcat()
146
      fid2=fopen(fullName2,'w');
147
      for i=1:length(lagIndex)
148
         colCounter=1;
149
          fprintf(fid2,'%f\t',lagIndex(i));
150
         while ZhTotal(i,colCounter)~=0
151
              fprintf(fid2,'%f\t',ZhTotal(i,colCounter));
152
              colCounter=colCounter+1;
153
              if(colCounter>2*nLag)
154
                 colCounter=colCounter-1;
155
                 break;
156
             end
157
         end
158
          fprintf(fid2,'\n');
159
     end
160
     fclose(fid2);
161
162
      %keep all the data
163
     lagIndex zygo=lagIndex;
164
      average heigth zygo=average heigth;
165
      ZhTotal zygo=ZhTotal;
166
167
168
      169
     noOfReplication=1;
170
     filePath ='ANAS Resolution data\';
171
     filePathFolder=filePath;
172
173
     matVal = zeros(20e6,3); %NOTES: use pre-allocated memory (like in C/C++)
174
     where rhe variables are declared first.
175
     for j=1:noOfReplication
176
          filename='alicona5 1';
177
          fullName=[filePathFolder '\' filename '.txt'] %string concatenation,
178
      alternative to strcat()
179
         fid=fopen(fullName,'r'); %opening the file
```

```
180
          pointCounter=0;
181
          line counter=0;
182
183
          while (~feof(fid))
184
             readLine=fgetl(fid);
185
              if (~ischar(readLine))
186
                 break
187
              end
188
189
              val=regexp(readLine,' ','split'); %Splitting the string with
190
      certain delimiter
191
              if(size(val, 2) >= 3)
192
                  if(~isnan(str2double(val(3)))) %check if the z value is not NaN
193
                      pointCounter= pointCounter+1;
194
                      matVal(pointCounter,1) = str2double(val(1)); %*delta x;
195
                      matVal(pointCounter,2) = str2double(val(2)); %*delta y;
196
                      matVal(pointCounter, 3) = str2double(val(3)); %unit in ?
197
                  end
198
              end
199
200
          end %END of while
201
202
          fclose(fid);
203
204
      end %END of the inner for j
205
      matVal(pointCounter+1:end,:) = [];
206
207
208
      %%CALCULATING the heigth with respect to lateral distance-----
209
      nLag=pointCounter;
210
      ZhTotal = zeros(nLag,2*nLag); % column 1=for the value, 2=for the lag index
211
     var = zeros(1,nLag); % column 1=for the value, 2=for the lag index
      average heigth=zeros(1,nLag);
212
213
     lagIndex=zeros(1,nLag);
214
215
      lagIndexCounter=0;
216
     ZhColCounter=0;
217
218
      for i=1:pointCounter
219
          for j=1:pointCounter
220
              221
      %abs(matVal(i,1)-matVal(j,1));
222
              if(j\sim=i)
223
                  if(i==1)
224
                     lagIndexCounter=lagIndexCounter+1;
225
                      lagIndex(lagIndexCounter) = lag; % record all the possible
226
      lag
227
                      %ZhColCounter=ZhColCounter+1;
228
                      ZhTotal(lagIndexCounter,1) = abs(matVal(i,3) - matVal(j,3));
229
230
                  else
231
                      counter=1;
232
                      while ((lagIndex(counter)-lag)> 0.05)
233
      %lagIndex(counter)~=lag %if the difference < 0.05 um, they are the same</pre>
234
                          counter=counter+1;
235
                          if (counter>nLag)
236
                              counter=counter-1;
237
                              break;
238
                          end
```

```
239
                      end
240
                      colCounter=1;
241
                      while(ZhTotal(counter, colCounter) ~=0)
242
                          colCounter=colCounter+1;
243
                          if(colCounter>2*nLag)
244
                              colCounter=colCounter-1;
245
                              break;
246
                          end
247
                      end
248
                      ZhTotal(counter, colCounter) = abs(matVal(i,3) - matVal(j,3));
249
                  end
250
              end
251
          end
252
      end
253
      lagIndex;
254
      ZhTotal;
255
256
      %calculating the average heigth
257
      average heigth(lagIndexCounter+1:end)=[];
258
      lagIndex(lagIndexCounter+1:end) = [];
259
      for i=1:lagIndexCounter
260
          average heigth(i)=0;
261
          \dot{1}=1;
262
          colCounter=1;
263
          while ZhTotal(i,colCounter)~=0
264
              average heigth(i) = average heigth(i) + ZhTotal(i, colCounter);
265
              colCounter=colCounter+1;
266
               if(colCounter>2*nLag)
267
                  colCounter=colCounter-1;
268
                  break;
269
               end
270
          end
271
          average heigth(i) = average heigth(i) / colCounter;
272
      end
273
      average heigth;
274
275
      %______
276
277
      figure;
278
      plot(lagIndex,average heigth,'.');
279
      ylabel('Average height/um');
280
      xlabel('lateral distance/um');
281
      title('Alicona data');
282
283
      matrix size=size(matVal);
284
285
      %WRITING The data to File: lagIndex, avergae height, ZhTotal
      fullName2=[filePathFolder '\' filename '-lagIndex_ALICONA.txt'] %string
286
287
      concatenation, alternative to strcat()
288
      fid2=fopen(fullName2,'w');
289
      for i=1:length(lagIndex)
290
          fprintf(fid2,'%f\n',lagIndex(i));
291
      end
292
      fclose(fid2);
293
294
      fullName2=[filePathFolder '\' filename '-averageHeight ALICONA.txt']
295
      %string concatenation, alternative to strcat()
296
      fid2=fopen(fullName2,'w');
297
      for i=1:length(lagIndex)
298
          fprintf(fid2,'%f\n',average heigth(i));
```

359

```
299
      end
300
      fclose(fid2);
301
302
     fullName2=[filePathFolder '\' filename '-zhTotal ALICONA.txt'] %string
303
      concatenation, alternative to strcat()
304
      fid2=fopen(fullName2,'w');
305
      for i=1:length(lagIndex)
306
          colCounter=1;
307
          fprintf(fid2,'%f\t',lagIndex(i));
308
          while ZhTotal(i,colCounter)~=0
              fprintf(fid2,'%f\t',ZhTotal(i,colCounter));
309
310
              colCounter=colCounter+1;
311
              if(colCounter>2*nLag)
312
                  colCounter=colCounter-1;
313
                  break;
314
              end
315
          end
316
          fprintf(fid2,'\n');
317
318
      fclose(fid2);
319
320
      %keep all the data
321
      lagIndex alicona=lagIndex;
322
      average_heigth_alicona=average_heigth;
323
      ZhTotal alicona=ZhTotal;
324
325
326
      327
      height transmission=zeros(length(lagIndex alicona),2)
328
      for i=1:length(lagIndex alicona)
329
330
          for j=1:length(lagIndex zygo)
331
              %if(lagIndex alicona(i) == lagIndex zygo(j))
332
              threshold=0.05;
333
              if(abs(lagIndex alicona(i)-lagIndex zygo(j))<threshold)</pre>
334
                  height transmission(i,1)=lagIndex alicona(i);
335
                  height transmission(i,2)=100-(100*(abs(average height zygo(j)-
336
      average heigth alicona(i))/average heigth zygo(j))); %in percentage
337
                  break
338
              end
339
          end
340
      end
341
342
343
      plot(height transmission(:,1),height transmission(:,2),'.');
344
      xlabel('Lateral distance/um');
345
      ylabel('Transmitted height/%');
346
      title('Transmission curve');
347
348
349
      fullName2=[filePathFolder '\' filename '-Transmission curve.txt'] %string
350
      concatenation, alternative to strcat()
351
      fid2=fopen(fullName2,'w');
352
      for i=1:length(lagIndex)
353
          fprintf(fid2,'%f\n',height transmission(i));
354
      end
355
      fclose(fid2);
356
357
      CPUTime=toc
358
```